

Copyright © 1981, by the author(s).
All rights reserved.

Permission to make digital or hard copies of all or part of this work for personal or classroom use is granted without fee provided that copies are not made or distributed for profit or commercial advantage and that copies bear this notice and the full citation on the first page. To copy otherwise, to republish, to post on servers or to redistribute to lists, requires prior specific permission.

A UNIFIED CAD MODEL FOR MOSFETS

by

S. Liu

Memorandum No. UCB/ERL M81/31

20 May 1981

S. Liu

A UNIFIED CAD MODEL FOR MOSFETS

by

Sally Liu

Memorandum No. UCB/ERL M81/31

20 May 1981

ELECTRONICS RESEARCH LABORATORY

College of Engineering
University of California, Berkeley
94720

ABSTRACT

The operation of Metal-Oxide-Semiconductor Field-Effect Transistors is analyzed, emphasizing the effects of quantum-mechanical statistics, the joining of strong- and weak-inversion regions and the modeling of small-geometry devices.

When the gate voltage exceeds the threshold voltage, the surface-carrier concentration is higher than the doping concentration and the surface may degenerate. In order to understand the changes at the surface, we must explore the quantum-mechanical effects. The quantum-mechanical effects must be ascribed to both the quantum-mechanical statistics and the quantization of the energy band. Numerical evaluation of the drain current, channel conductance etc., based upon quantum-mechanical statistics, demonstrates that quantum-mechanical statistics alone do not result in a significant deviation from the classical prediction of these device characteristics within practical operational voltage ranges.

When the gate voltage changes from above to below the threshold voltage, the operational mode shifts from strong to weak inversion. The difficulties in modeling the transition between the strong- and weak-inversion regions, where no simple approximations can be applied, are overcome by joining the strong- and weak-inversion characteristics by properly defining the transition region. This approach provides an efficient and self-consistent way to simulate the operations of both strong- and weak-inversion regions.

Program TWIST has been developed to simulate the characteristics of weak inversion and weak-injection punchthrough by solving the two-

dimensional Poisson equation. The generation of non-uniform doping profiles including a two-dimensional impurity redistribution and graded meshes, and the application of modified Gummel's algorithm and Successive-Over-Relax iteration, together with a by-pass scheme, are implemented.

The punchthrough phenomena are explored by theoretical analysis and two-dimensional device simulations. The results of the two-dimensional simulations establish the relationship between the drain-induced lowering of the surface barrier and the punchthrough. The onset voltage of the punchthrough is derived from a quasi one-dimensional Poisson equation.

To provide an efficient model of small-geometry devices, a semi-empirical model, MOS3, has been developed and installed into the circuit simulation program SPICE2.G. The equations in a simple format allow easy parameter extraction, a property which is as critical as the accuracy of the model itself. A close correlation is obtained between the calculated and measured characteristics of small-geometry devices.

ACKNOWLEDGEMENTS

The author wishes to express her sincere appreciation to Professor D.O.Pederson for his continuing encouragement and guidance throughout the course of this work. She also gratefully acknowledges the numerous helpful discussions with Professors B.Hoefflinger, A.R.Newton and A.M.Portis. It is her pleasure to acknowledge the steady and helpful discussions with E.Cohen, A.Vladimirescu and the other members of the CAD group at the University of California, Berkeley.

Both the financial and technical support received from the Signetics Corporation and the encouragement provided by T.Young are gratefully acknowledged. Special thanks are extended to P.T.Chuang for many interesting discussions in the early stages of this work.

The predoctoral fellowship from IBM for the spring and fall of 1976 helped the preliminary development of this research. The generous equipment grant from the Hewlett-Packard Company and the extensive computer resources supplied by the Computer Center of the University of California, Berkeley are also acknowledged.

The author is especially indebted to Mrs. E.A.Baker for her careful proofreading of the entire manuscript.

The author wishes to express her deep gratitude to her parents, Kuei-Ju and Hui-Hsiang, for their support and encouragement throughout the course of this work.

TABLE OF CONTENTS

CHAPTER 1: Introduction	1
CHAPTER 2: The Quantum-Mechanical Effects on the Operation of MOSFETs	5
2.1. A Survey of the El-Mansy and Boothroyd Model	6
2.2. The Impact of Quantum-Mechanics	13
2.2.1. The Wave Property and the Band Quantization	14
2.2.2. Fermi-Dirac Statistics	15
2.2.3. The Impact on Device Characteristics	17
CHAPTER 3: A Unified Approach to MOSFET Modeling	19
3.1. General Overview	20
3.2. Strong-Inversion Region	25
3.3. Weak-Inversion Region	27
3.4. Join Together	28
3.5. The Influence of Fast-Surface States	31
CHAPTER 4: Two-Dimensional Simulations of Small-Geometry MOSFETs	33
4.1. Overview of Program TWIST	35
4.2. Graded Mesh and Impurity Distribution	36
4.3. Basic Equations and Boundary Conditions	37
4.4. Quasi-Fermi Level	39
4.5. Potential Initialization	42
4.6. Iteration Algorithm and Program Performance	44
4.7. Device Characteristics	45
CHAPTER 5: The Punchthrough	47
5.1. Static Feedback and Punchthrough	48

5.2. The Saddle Point	50
5.3. Quasi-One-Dimensional Analysis	51
CHAPTER 6: Small-Geometry Effects and the Semi-empirical Model MOS3	56
6.1. Threshold Voltage	58
6.1.1. Short-Channel Effects	59
6.1.2. Narrow-Channel Effect	60
6.1.3. The Model Equations	61
6.2. Basic Drain-Current Equation	62
6.3. Surface-Mobility Modulation by Gate Voltage	64
6.4. Velocity Saturation of Hot Electrons	64
6.5. Saturation Voltage	65
6.6. Channel-Length Modulation	67
6.7. Capacitance Model with Charge Conservation	68
6.8. The Comparison Between MOS2 and MOS3	69
CHAPTER 7: Summary	73
APPENDIX A: TWIST User's Guide	77
APPENDIX B: Example Input to Program TWIST	90
APPENDIX C: Example Console Session of Program TWIST	92
APPENDIX D: Test-Circuit Inputs to SPICE2.G	97
APPENDIX E: Listing of Program TWIST	105
REFERENCES	179

CHAPTER 1

Introduction

A Metal-Oxide-Semiconductor Field-Effect Transistor (MOSFET), also commonly known as an Insulated-Gate Field-Effect Transistor (IGFET), is a semiconductor device with four terminals: source, drain, gate and substrate. It is the major ingredient of today's Large- and Very-Large-Scale Integrated Circuits (LSI/VLSI). The extensive development of MOS technology is a result of the simplicity of its structure. This simple structure permits low production costs and high packing density which make MOS integrated circuits very economical.

The invention of MOSFETs can be traced to the 1930's [1-2]. The first reported laboratory study of MOSFETs was carried out in the 1940's [3]. Commercial MOSFETs became available in the 1960's [4], after the development of planar integrated-circuit technology [5]. Since then, MOS technology has been developed rapidly [6-7]. First, the polysilicon gate replaced the metal gate. Then ion implantation [8-10] replaced thermal diffusion and the devices could be tailored with much more freedom and precision. The devices are getting smaller and smaller. Today's typical channel length and width are as small as $2\mu m$. Now, people are looking forward to the era of devices as small as or even smaller than $1\mu m$.

Theoretical research on MOSFETs and technological improvements have always gone hand in hand. Detailed physical analysis has led to better understanding of device operations and to the development of transistor models that are widely used in circuit simulation programs. Device models which are compatible with these simulators have gained very much attention. Characteristics equations with sets of device parameters are often used [11].

Table-Look-Up is an alternative when dealing with large-scale circuits [12-13]. Both approaches to transistor modeling require either available device data from which parameters may be extracted [14] or parameter values obtained from one-dimensional or pseudo-two-dimensional physical models of the transistors [15]. Numerous models have been developed [6-7]. The complexity ranges from the most compact Shichman-Hodge's [16] model to those models requiring iterative solutions [17]. A good CAD (Computer-Aided-Design) model should be able not only to reflect the state of the technology but also to provide accuracy and computational efficiency.

Most MOSFET circuits are designed so that the devices operate in the strong-inversion region. The strong-inversion region is the region in which the concentration of the minority carriers exceeds that of the majority carriers, which is in the range of 5.0×10^{14} to $5.0 \times 10^{16} \text{ cm}^{-3}$. The presence of excessive minority carrier concentration inverts the type of net surface concentration. The threshold voltage of strong inversion is usually on the order of 1 volt. Degeneracy, the condition in which the surface concentration is 10^{19} cm^{-3} or more, does not occur until a much higher gate voltage is reached. The impact of this heavy concentration and the effect due to quantum mechanics are explored in Chapter 2.

The current in the weak-inversion region is low. The transition between strong- and weak-inversion regions deserves attention. The major difficulty in modeling the transition region is the fact that no simple physical approximation can be applied. In the transition region, the contributions from the minority and majority carriers are comparable. Both the diffusion and drift currents are equally important. Chapter 3 describes a properly defined transition region in which the strong- and weak-inversion characteristics are joined. This approach does not involve internal iterations and provides both efficiency and accuracy in circuit simulations.

Numerical solutions of the two-dimensional potential and current-continuity equations are necessary to describe the new generation of integrated MOSFETs, which are shorter and/or narrower than the old ones. People have been working on these subjects for the past ten years [18-20]. Initially, idealized impurity distributions and junction boundaries were assumed to facilitate solutions. However, with very small device geometries, modern process simulators show extremely inhomogeneous two-dimensional impurity distributions and junction boundaries, which must then be considered in the potential and current-transport simulations. Program TWIST (TWO-dimensional Interactive Simulation of MOS Transistors) is an interactive device simulation program which handles the solution of the two-dimensional Poisson equation. Because it limits the solution to the Poisson equation only, TWIST is useful both as a pre-selector for structures to be simulated with a more elaborate two-dimensional potential and current-transport program and as an efficient simulation tool for the conditions of weak inversion and/or weak-injection punchthrough. The development of Program TWIST is described in Chapter 4.

One of the most important problems in designing small-geometry MOSFETs is the punchthrough between the source and the drain. This is the result of barrier lowering due to the merging of the source and drain depletion regions. Once the punchthrough condition is reached, the current flowing from the source to the drain increases significantly as V_{DS} increases, and the device characteristics deviate from the norm. This additional current can be viewed as an undesirable component to be avoided or exploited as part of the conduction current in novel applications of MOSFETs. In Chapter 5, the punchthrough phenomenon is explored by both theoretical analysis and two-dimensional device simulations using Program TWIST. The derivation of the onset voltage of punchthrough is based upon the assumption of a uniform substrate doping profile.

The ultimate difficulty in the development of a model suitable for small devices is the correct treatment of the two-dimensional nature of the potential distribution and current flow. A semi-empirical modeling approach is a compromise between simulation accuracy and computational efficiency. The equations in a simple format allow easy parameter extraction, a property which is as critical as the accuracy of the model itself. The MOS3 model has been developed and implemented into the circuit simulation program SPICE2 to provide an accurate model of MOSFETs no larger than $L \leq 2\mu m$ and/or $W \leq 2\mu m$, and to attain computational efficiency.

In developing the MOS3 model, several important issues of MOSFET modeling were considered. Model equations were developed and verified. In the future, modeling work should emphasize the small-geometry effects. Further development of two-dimensional device simulation programs would be very helpful.

CHAPTER 2

The Quantum-Mechanical Effects on the Operation of MOSFETs

In the El-Mansy and Boothroyd model [21-22], hereafter abbreviated the E-B model, one of the major issues is the impact of quantum-mechanical statistics on device characteristics and modeling. The E-B model and the nature of the quantum-mechanical effects are examined in this chapter.

The E-B model is a charge-moment model based upon classical statistics and the assumption of a block-charge distribution. The authors argue that the widely observed channel-conductance modulation by the gate voltage can be attributed to quantum-mechanical statistics, not the surface-mobility modulation. But, in this aspect, their model does not perform better than models using empirical mobility equations.

The quantum-mechanical effects should be attributed to both the degeneracy of the surface carrier population, which can be described properly only by Fermi-Dirac statistics, and the wave property of the carriers, which leads to the quantization of energy band at degeneracy. The statistical impact alone is not large enough to cause a significant difference in the device characteristics in the practical operational range. The onset voltage of degeneracy is calculated. The surface potentials based upon different statistics vary by as much as 30 percent in a degenerate state, but the difference in the device characteristics is less than 1 percent.

An empirical expression, which relates the surface potential to the charge density per unit area in the degenerate case, is proposed. This expression is correct within three percent for Fermi levels within $+4$ to $-4 \frac{kT}{q}$ from the energy-band edge. This range, at room temperature, goes up

to approximately $(V_{GB} - V_{FB}) = 30V$ which is well above the maximum bias of practical MOSFET analog circuits. This expression is chosen so that it is differentiable and integratable and permits efficient computations.

2.1. A Survey of the El-Mansy and Boothroyd Model

The E-B model is an analytical model which covers both the strong- and weak-inversion regions of enhancement MOSFETs with a uniformly doped substrate. Basically, it differs from other models in its assumption of charge distribution rather than in its treatment of fundamental statistics. This point has been debated by Brews [23].

An N-channel MOSFET is shown in Figure 2.1. In that figure, L is the distance between the source and drain junctions, W is the width of the channel region, T_{OX} is the oxide thickness, x_j is the depth of the source and drain junctions, and x and y are the spatial coordinates to be used in later analysis. In the E-B model, in order to deal with the spatial charge distribution effect on the potential distribution, the total charges inside the semiconductor, including both the inversion and depletion charges, assume a step distribution [24] of concentration N_S and depth W_S as shown in Figure 2.2. In the case of an N-channel device, the potential, ϕ_s , sustaining this block of charge can be expressed as:

$$\phi_s = \frac{qN_S}{2\epsilon_{si}} W_S^2 \quad (2.1)$$

which is also the surface potential with the substrate potential taken as the reference point. The amount of gate charge per unit area, $Q_g = C_{OX}(V_{GB} - V_{FB} - \phi_s)$, must equal the amount of the total semiconductor charge per unit area, $Q_{SI} = -qN_S W_S$, to satisfy the constraint of charge neutrality. Therefore:

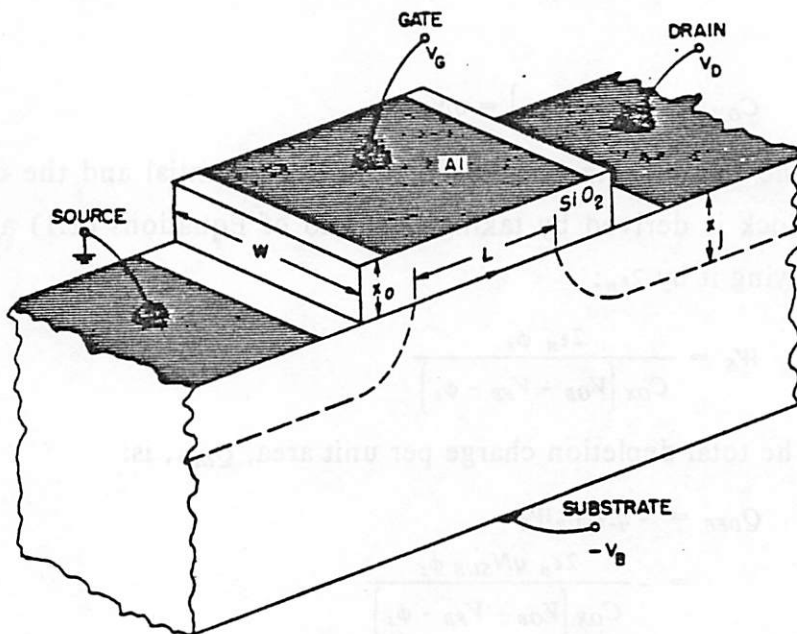


Figure 2.1 The Schematic Diagram of a MOSFET,

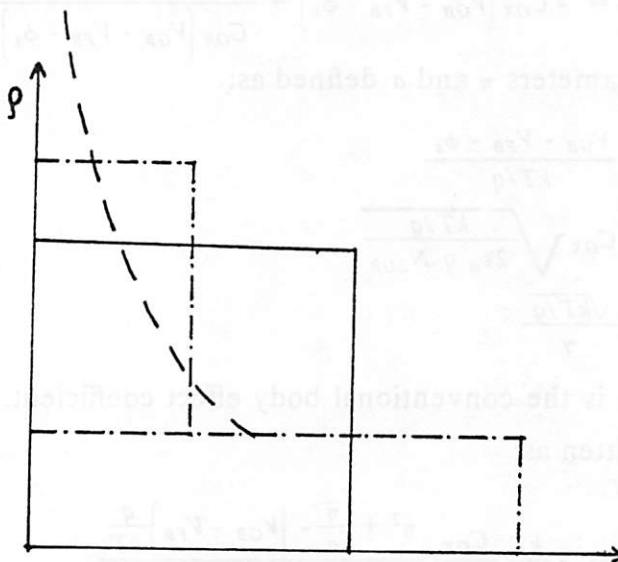


Figure 2.2 The Block Approximation of Charge Distribution in the E-B Model,

$$C_{OX} \left(V_{GB} - V_{FB} - \phi_s \right) = qN_S W_S \quad (2.2)$$

The relationship between the surface potential and the depth of this charge block is derived by taking the ratio of Equations (2.1) and (2.2) and multiplying it by $2\epsilon_{si}$:

$$W_S = \frac{2\epsilon_{si} \phi_s}{C_{OX} \left(V_{GB} - V_{FB} - \phi_s \right)} \quad (2.3)$$

The total depletion charge per unit area, Q_{DEP} , is:

$$Q_{DEP} = -qN_{SUB}W_S \quad (2.4)$$

$$= -\frac{2\epsilon_{si} qN_{SUB} \phi_s}{C_{OX} \left(V_{GB} - V_{FB} - \phi_s \right)} \quad (2.5)$$

where N_{SUB} is the substrate concentration. The inversion charge density, Q_{INV} , equals the negative sum of the gate and depletion charge densities:

$$Q_{INV} = - \left(Q_g + Q_{DEP} \right) \quad (2.6)$$

$$= -C_{OX} \left(V_{GB} - V_{FB} - \phi_s \right) + \frac{2\epsilon_{si} qN_{SUB} \phi_s}{C_{OX} \left(V_{GB} - V_{FB} - \phi_s \right)} \quad (2.7)$$

with parameters η and a defined as:

$$\eta = \frac{V_{GB} - V_{FB} - \phi_s}{kT/q} \quad (2.8)$$

$$a = C_{OX} \sqrt{\frac{kT/q}{2\epsilon_{si} q N_{SUB}}} \quad (2.9)$$

$$= \frac{\sqrt{kT/q}}{\gamma} \quad (2.10)$$

where γ is the conventional body effect coefficient. The expression Q_{INV} can be rewritten as:

$$Q_{INV} = -\frac{kT}{q} \frac{C_{OX}}{a} \frac{\eta^2 + \frac{\eta}{a} - \left(V_{GB} - V_{FB} \right) \frac{q}{kT}}{\eta} \quad (2.11)$$

This is Equation (25) in Reference [21]. Here, it has been derived solely based upon the assumption of block-charge distribution and is independent of the statistics on which the model is based.

The drain current is the most important device characteristic and can be obtained by integrating the total current density, $J(x,y)$, over a cross section normal to the channel direction:

$$I_{DS} = W \int_0^{w_y} J(x,y) dx \quad (2.12)$$

where w_y is the width of the surface charge layer at location y . The total current density is the sum of the drift and diffusion current densities:

$$J(x,y) = qU_{EFF} \left[N(x,y)E_y + \frac{kT}{q} \nabla_y N(x,y) \right] \quad (2.13)$$

Based upon Boltzmann statistics, the electron density is related to the quasi-Fermi level, ζ_n , which measures the excess charge induced by the external biases, as shown in the following expression:

$$N(x,y) = N_o e^{\frac{q(\phi(x,y) - \zeta_n)}{kT}} \quad (2.14)$$

where N_o is the electron density at zero biases. The total current density can be rewritten as:

$$J(x,y) = -qU_{EFF} N(x,y) \nabla_y \zeta_n \quad (2.15)$$

which is Equation (21) in Reference [21]. The drain current equation becomes:

$$I_{DS} = WqU_{EFF} \int_0^{w_y} N(x,y) \frac{\partial \zeta_n}{\partial y} dx \quad (2.16)$$

$$= -WU_{EFF} Q_{INV} \frac{\partial \zeta_n}{\partial y} \quad (2.17)$$

By integrating both sides of the above equation from source to drain in variable y , one arrives at Equation (24) of Reference [21]:

$$I_{DS} = -\frac{W}{L} U_{EFF} \int_0^{v_{DS}} Q_{INV} d\zeta \quad (2.18)$$

As noted before, Q_{INV} is an explicit function of ϕ_s . In order to carry out the integration in the above equation, ϕ_s must be related to the biases and the

quasi-Fermi level. This is achieved by integrating the differential Poisson equation in the potential domain from 0 to ϕ_s with the boundary condition of zero electric field at the boundary of zero potential:

$$\int_0^{\phi_s} \nabla_x^2 \phi d\phi = \frac{q}{\epsilon_{si}} \int_0^{\phi_s} [N - N_{SUB}] d\phi \quad (2.19)$$

$$\frac{1}{2} \left[\frac{\partial \phi}{\partial x} \right]_s^2 = \frac{q}{\epsilon_{si}} \int_0^{\phi_s} N(\phi) d\phi - \frac{q}{\epsilon_{si}} N_{SUB} \phi_s \quad (2.20)$$

It can be further rewritten as:

$$\int_0^{\phi_s} N(\phi) d\phi = \frac{Q_{SI}^2}{2\epsilon_{si}q} + N_{SUB}\phi_s \quad (2.21)$$

By applying the classical definition of the quasi-Fermi level, carrying out the integration, and replacing the expression Q_{SI} , Equation (8) in Reference [21] is obtained:

$$\frac{N_I^2}{N_{SUB}} \frac{kT}{q} e^{\frac{q(\phi_s - \phi_n)}{kT}} = \frac{[C_{OX}(V_{GB} - V_{FB} - \phi_s)]^2}{2\epsilon_{si}q} N_{SUB}\phi_s \quad (2.22)$$

ϕ_s must be solved from the above equation by either iteration or simplifying the equation. The integration in Equation (2.18) can be carried out:

$$I_{DS} = \frac{W}{L} U_{EFF} C_{OX} I^o \quad (2.23)$$

where

$$I^o = \left[V_{GB} - V_{FB} + 2\frac{kT}{q} + \gamma^2 - \frac{\phi_{s,S} + \phi_{s,D}}{2} \right] (\phi_{s,D} - \phi_{s,S}) - \gamma^2 \left[\gamma^2 - V_{GB} \right] \left[\frac{V_{GB} - V_{FB} - \phi_{s,D}}{V_{GB} - V_{FB} - \phi_{s,S}} \right] \quad (2.24)$$

which is equivalent to Equation (15) in Reference [21]. Here $\phi_{s,S}$ and $\phi_{s,D}$ are the surface potentials derived from Equation (2.20) at the source and the drain, respectively. Equation (2.24) has been intentionally rewritten in a format similar to that of conventional equations for a convenient comparison.

It might be argued that it is not necessary to introduce the classical definition of the quasi-Fermi level, which contradicts the quantum-mechanical concept put forth by El-Mansy and Boothroyd. To accommodate their argument, Equation (21) of Reference [21] must be derived using a quantum-mechanical approach. Nonetheless, the authors of the E-B model maintain that because the properties of the source and drain junctions are well described by Boltzmann statistics, the first-moment of charge distribution based upon different statistics should be the same at the junction boundaries to provide a smooth transition. They further argue that this is a general property of the Poisson equation and can be applied to the derivation of the drain current equation. This direct application of the boundary condition to the channel region is confusing and contradictory to their main theme. Both Equations (8) and (21) in Reference [21] are the results of classical statistics.

The essence conveyed by the combination of the step charge distribution and the classical voltage-potential relationship can be properly designated as a classical charge-moment model [25]. In the charge-block picture, the total amount of charge inside the semiconductor is the weighted sum of the inversion and depletion charges:

$$Q_{SI} = \sigma_{INV} Q_{INV,o} + \sigma_{DEP} Q_{DEP,o} \quad (2.25)$$

where the weighting factors σ_{INV} and σ_{DEP} are defined as:

$$\sigma_{INV} = \frac{W_S}{W_{INV}} \quad (2.26)$$

$$\sigma_{DEP} = \frac{W_S}{W_D} \quad (2.27)$$

and

$$W_{INV} = 2 \frac{\int_0^{\infty} x \rho_{INV}(x) dx}{\int_0^{\infty} \rho_{INV}(x) dx} \quad (2.28)$$

$$W_D = \frac{\int_0^{\infty} \rho_{DEP}(x) dx}{N_{SUB}} \quad (2.29)$$

σ_{INV} is a number greater than one, while σ_{DEP} is a number less than one. W_{INV} , W_D and W_S versus $V_{GB} - V_{FB}$, and σ_{INV} and σ_{DEP} versus $V_{GB} - V_{FB}$ are plotted in Figures 2.3 and 2.4, respectively, for comparison. In the strong-inversion region, the weighting factor of the depletion charge decreases as the gate voltage increases. Thus, the depletion charge in the E-B model diminishes as V_{GB} increases. Nonetheless, it should not be interpreted as a diminution of the real depletion charge.

The charge-block representation enables the E-B model to replace the double integration in the Pao-Sah theory [26] by a closed-form expression and establishes it as a practical CAD model. But quantum mechanics are not involved in the derivation of the model.

The E-B model also differs from the other models in that it uses a constant, instead of modulated, surface mobility. The drain conductance can be derived by differentiating the drain current equation with respect to the drain to source voltage, V_{DS} :

$$G_{DS} = -\frac{W}{L} U_{EFF} Q_{INV}(drain) \quad (2.30)$$

$$= -\frac{W}{L} U_{EFF} [Q_{SI} - Q_{DEP}] \quad (2.31)$$

Clearly, the drain-conductance modulation may result from variations in the surface mobility, the surface potential or the depletion charge or in all three of them. In the E-B model, the drain-conductance modulation is the consequence of repartitioning charges. The weighting factor of the depletion

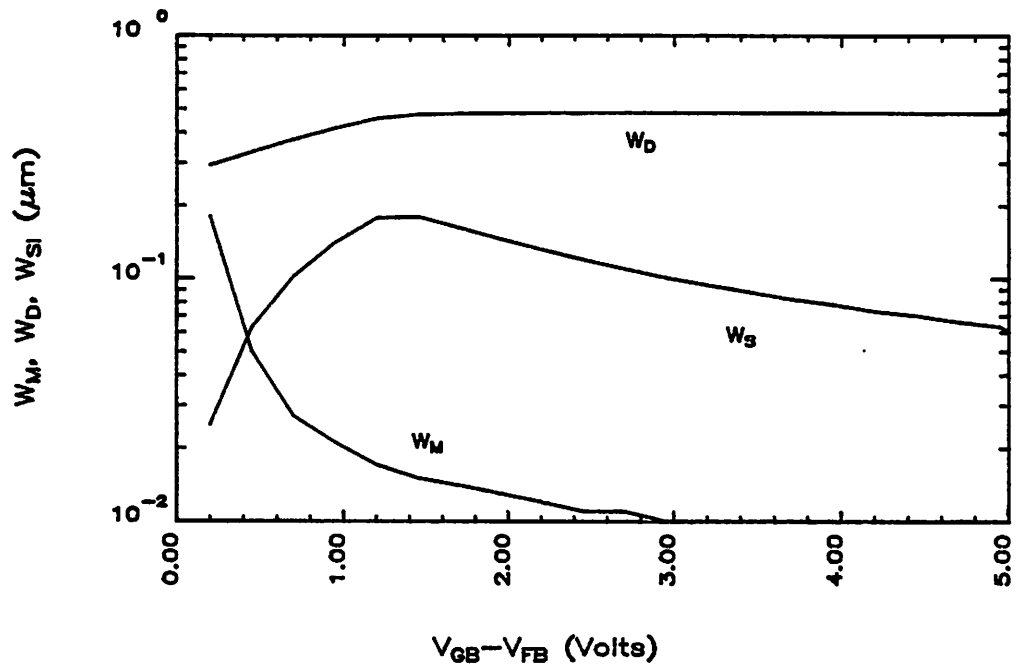


Figure 2.3 The Step Widths of Depletion and Inversion Charges and the Block Charge in the E-B Model,

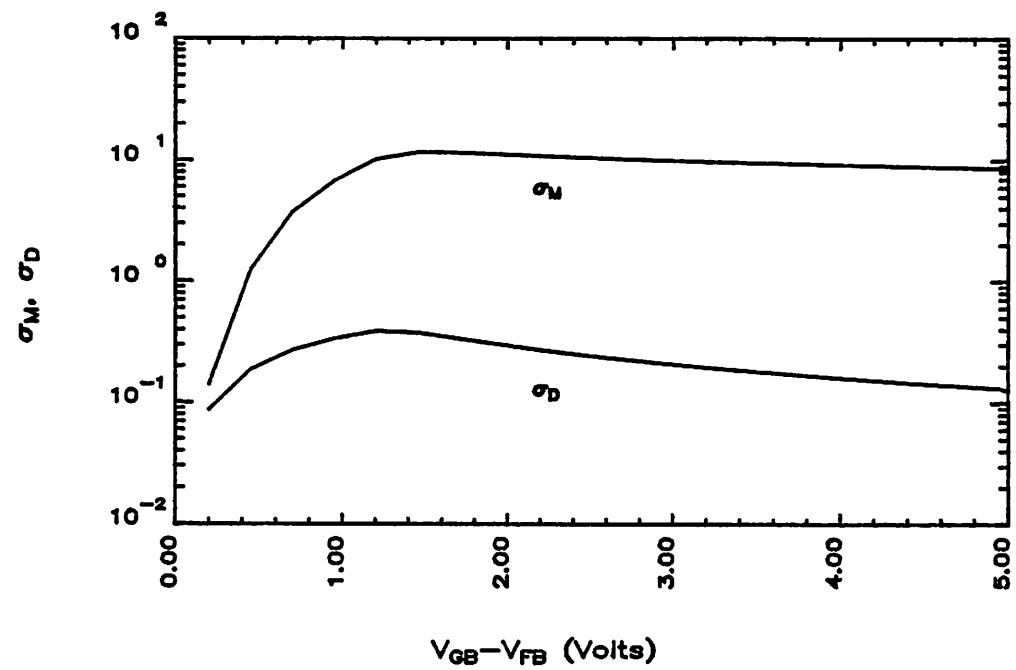


Figure 2.4 σ_{INV} and σ_{DEP} , Weighting Factors of Inversion and Depletion Charges, in the E-B Model,

charge is sensitive to the gate voltage as indicated in the formulation of Q_{DEP} . Conventionally, the drain-conductance modulation is modeled by empirical mobility modulation. In this aspect, the E-B model is less flexible than models using empirical mobility-modulation concept. The I_{DS} -versus- V_{DS} curves of a $50\mu m$ by $9\mu m$ MOSFET are plotted in Figure 2.5. The measured data is compared with both the E-B model and the MOS2 model in SPICE2D, which uses the empirical mobility-modulation approach. At the low bias range of 0 to 0.5 volts V_{DS} , all the second-order effects are negligible and the simulated characteristics are dominated by the basic assumption. The E-B model consistently overestimates the current. The difference increases as the gate voltage increases. The model parameters of this device are chosen so that the models fit adequately in the range of 0 to 10 volts V_{DS} as shown in Figure 2.6. The parameter values are listed in Table 2.1:

Table 2.1			
Parameter	MOS2	E-B	Unit
W	50	50	μm
L	9	9	μm
VTO	0.45	0.45	V
TOX	950	950	Å
XJ	2.2	2.2	μm
LD	0.75	0.75	
NSUB	6E15	3E15	cm^{-3}
UO	630	550	$cm^2/V-s$
UEXP	0.27	-	
UCRIT	60K	-	V/cm

Table 2.1 Device Parameters Used in Figures 2.5 and 2.6

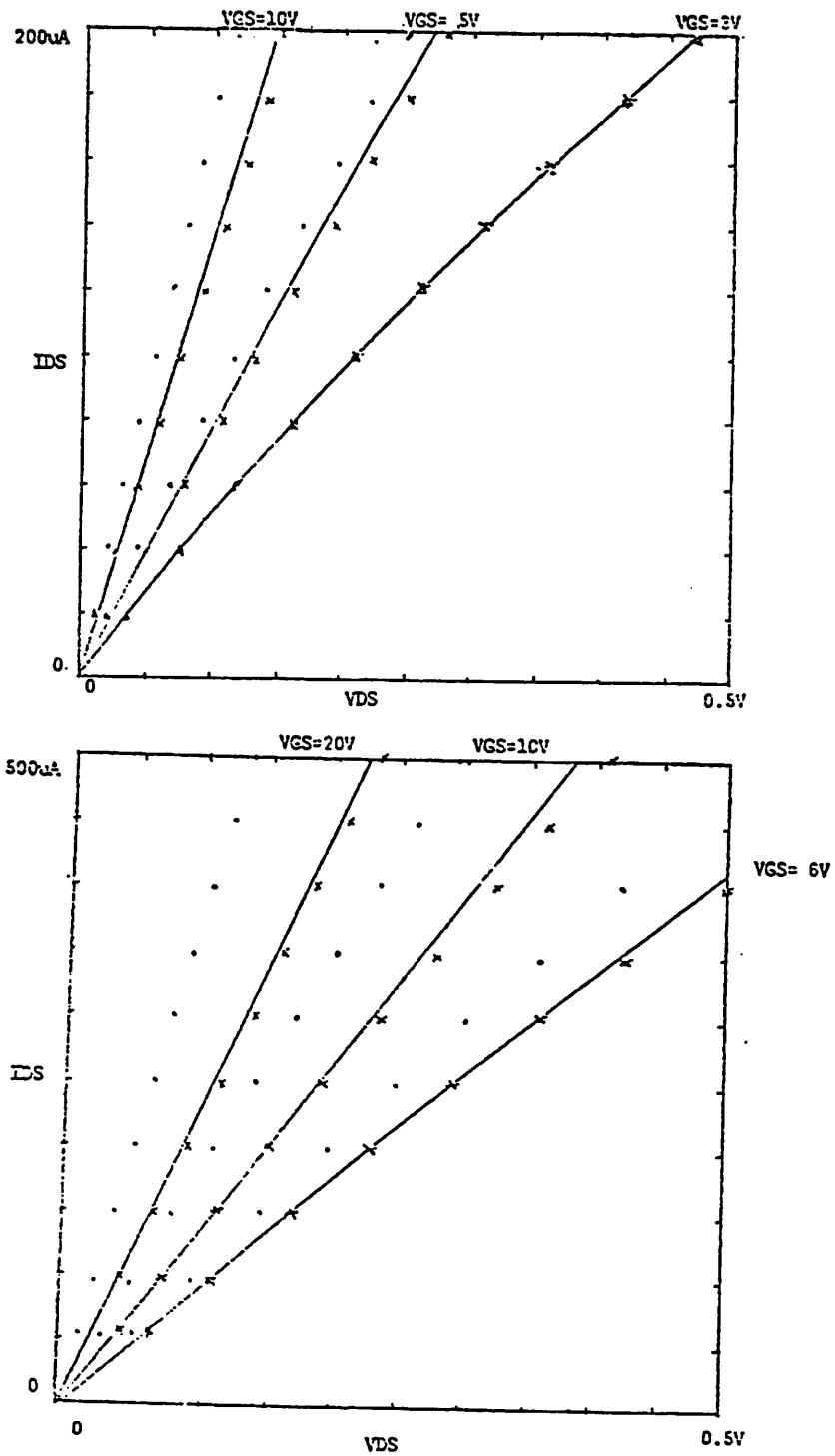


Figure 2.5 I_{DS} -Versus- V_{DS} of the Experimental Measurements and the MOS2 and E-B Models with Parameter V_{GS} in a Low V_{DS} Range,

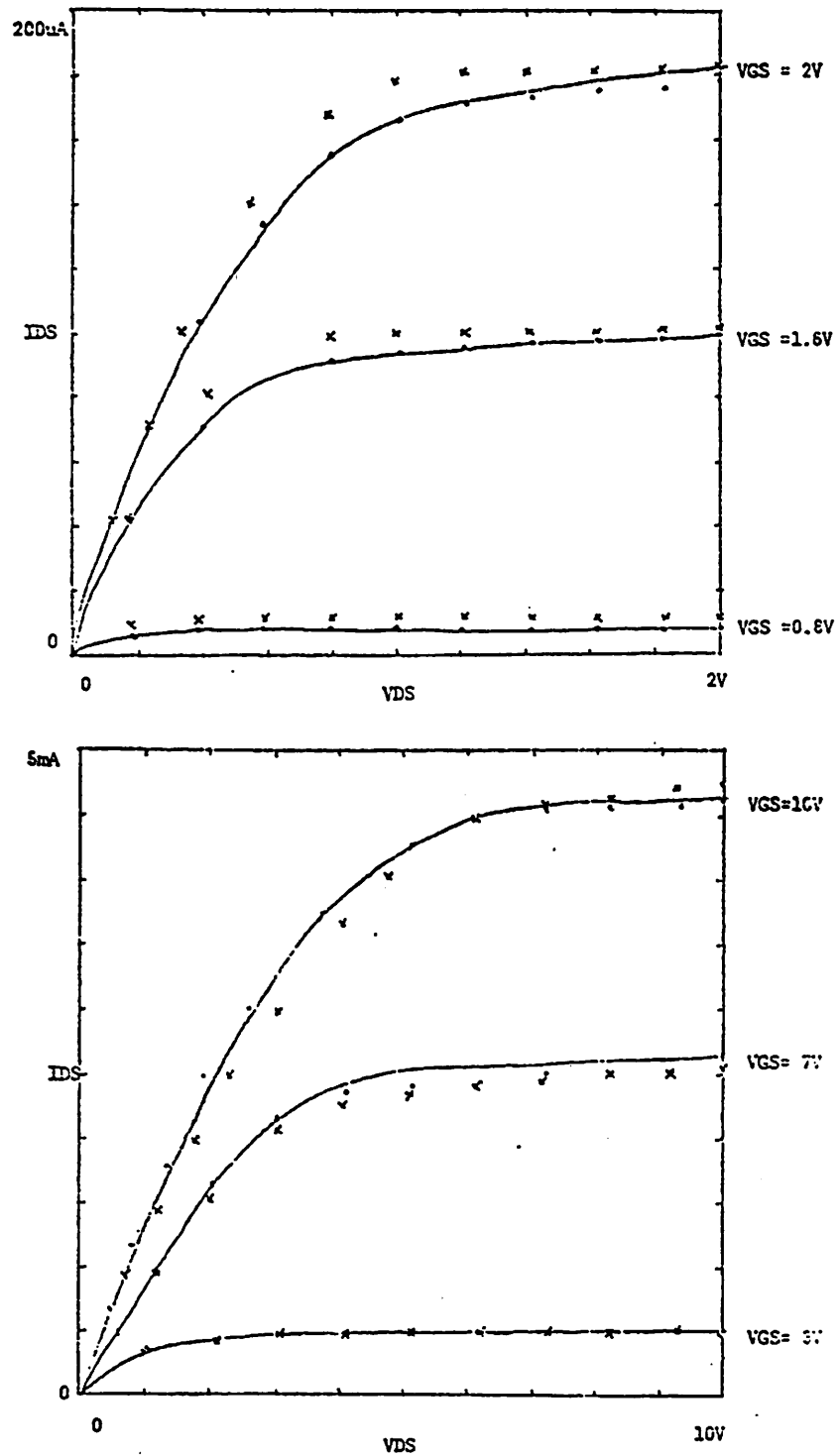


Figure 2.6 I_{DS} -Versus- V_{DS} of the Experimental Measurements and the MOS2 and E-B Models with Parameter V_{GS} in a High V_{DS} Range,

2.2. The Impact of Quantum-Mechanics

Equation (2.21) is a general derivation from the Poisson equation. Quantum-Mechanical statistics and the noticeable wave property in degeneracy induce different carrier distributions and integration results that deviate from the classical ones. A new relationship between the surface potential and the biases is required in order to handle the quantum-mechanical effects properly.

The surface potential measures the conducting carriers. Its distribution determines how the current will flow between the source and the drain. The surface potential predicted by quantum mechanics is more sensitive to the applied gate voltage than the classical statistics predicted.

The quantum-mechanical effects can be attributed to both the highly degenerate surface concentration, which can be properly described only by Fermi-Dirac statistics, and the wave property, which leads to the quantization of the surface energy band. The combined impact of both the statistics and the wave property has been studied by linearizing the surface-potential-well to decouple the Poisson and the Schrödinger equations [27], and using perturbation techniques to include the non-linearity of the potential well in the highly-degenerate case [28].

The maximum of the electron distribution function is located inside the semiconductor instead of at the surface which is predicted by Boltzmann statistics without including the effects of the Schrödinger equation. The peak concentration is much less than the classical one. As reported by the work of Talley et al. [27], the channel thickness decreases as the gate voltage increases, and stays at a finite thickness of approximately $0.01\ \mu\text{m}$. While classical statistics also predicts a decreasing channel thickness, but the thickness diminishes in the very strong-inversion region.

Pals [29] has measured the characteristics of capacitance versus gate voltage to determine the charge distribution inside a semiconductor. His results show that the quantum-mechanical considerations must be included in the theoretical calculations in order to match the experimental data. The existence of sub-bands has been demonstrated by magneto-resonance measurements [30] on P-channel MOSFETs.

2.2.1. The Wave Property and the Band Quantization

The influence of the wave property has been explored by precise numerical calculations based upon the Schrödinger and Poisson equations. The results of the existing studies are reviewed in the following paragraphs.

When the gate voltage is high enough to induce a degenerate surface carrier concentration, the wave property of the carriers becomes noticeable. The impenetrable potential barrier at the interface forces the interface be a node point of the standing wave pattern associated with the carrier distribution function. As shown in Figure 2.7, the fundamental energy states, which have the highest occupation probability, tend to place the peak carrier concentration close to the center of the surface potential well. So the carrier distribution based upon quantum-mechanical calculations has its peak concentration inside the semiconductor.

As the surface concentration degenerates, the surface conduction band is quantized and splits into sub-bands along a direction normal to the surface. Each of the sub-bands corresponds to a two-dimensional continuum. The carrier motion is quantized along the normal direction, but is continuous along the parallel direction. The quantization effect is enhanced as the surface potential well is narrowed down at an increasing substrate bias. At

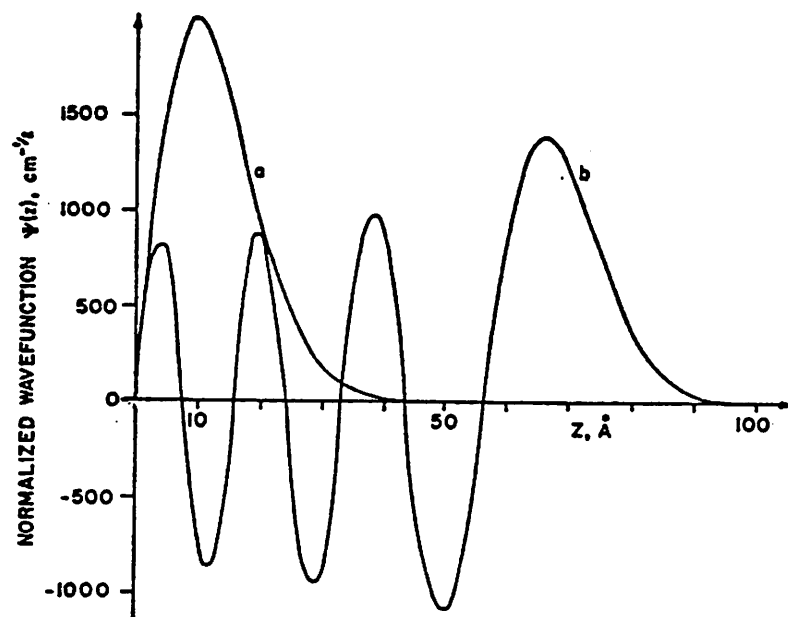


Figure 2.7 The Distribution Function of Inversion Carriers in the Low Energy States (from Reference [2.7]),

room temperature, when the surface just starts to invert, many of the sub-bands are populated and the quantization effect is not prominent. As the gate voltage increases, the surface's normal field strength, the differences among the quantized energy levels, and the relative population of the lowest sub-band all increase. Thus, the quantization effect is profound.

2.2.2. Fermi-Dirac Statistics

The carrier concentration can be expressed as:

$$N = \int_{E_0}^{E_1} N(E) F(E) dE \quad (2.32)$$

where $N(E)$ and $F(E)$ are the density of states and the distribution probability respectively. If the surface carrier concentration degenerates, the integration should be replaced by the summation over all the sub-bands, $N(E)$ by the corresponding density of each sub-band, and where $F(E)$ is Fermi-Dirac distribution function.

By using the Fermi-Dirac function, neglecting the sub-band quantization and assuming a spherical band structure, the above equation becomes:

$$N(\phi) = \frac{2}{\sqrt{\pi}} N_C F_{1/2} \left[\frac{E_F - E_C + q(\phi - \zeta_n)}{kT} \right] \quad (2.33)$$

where

$$F_{1/2}(x) = \int_0^{\infty} \frac{\eta^{1/2} d\eta}{1 + e^{\eta - x}} \quad (2.34)$$

and ϕ is the magnitude of band bending and ζ_n is the quasi-Fermi level. If the surface concentration does not degenerate, it can be reduced to:

$$N(\phi) = N_C e^{(E_F - E_C + q(\phi - \zeta_n))/kT} \quad (2.35)$$

which is equivalent to Equation (2.14) with $N_0 = N_C e^{(E_f - E_c)/kT}$. The

relationship between the surface potential and the gate voltage can be derived by substituting the expression $N(\phi)$ for the integrand on the left side of Equation (2.21). By using the approximations suggested by Seiwatz and Green [32], the integration can be reduced to [33]:

$$\int_0^{\phi_s} N(\phi) d\phi = \frac{kT}{q} N_C \frac{2}{\sqrt{\pi}} \frac{2}{3} F_{3/2} \left[E_F - E_C + q \frac{(\phi_s - \zeta_n)}{kT} \right] \quad (2.36)$$

where

$$F_{3/2}(x) = \int_0^{\infty} \frac{\eta^{3/2} d\eta}{1 + e^{\eta - x}} \quad (2.37)$$

The corresponding expression based upon Boltzmann statistics is:

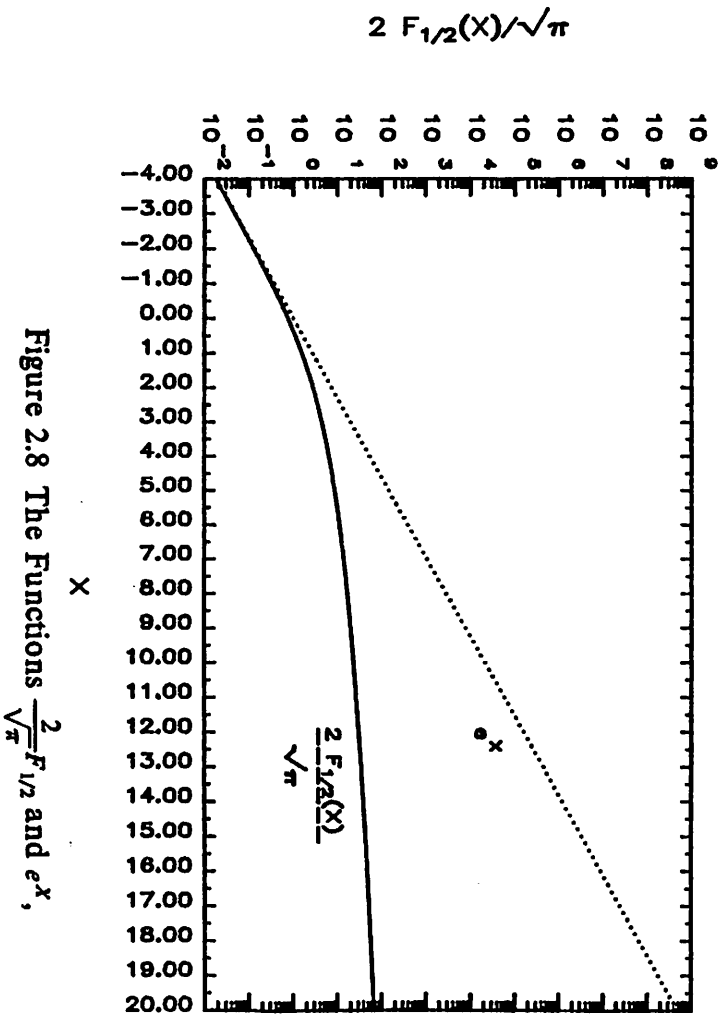
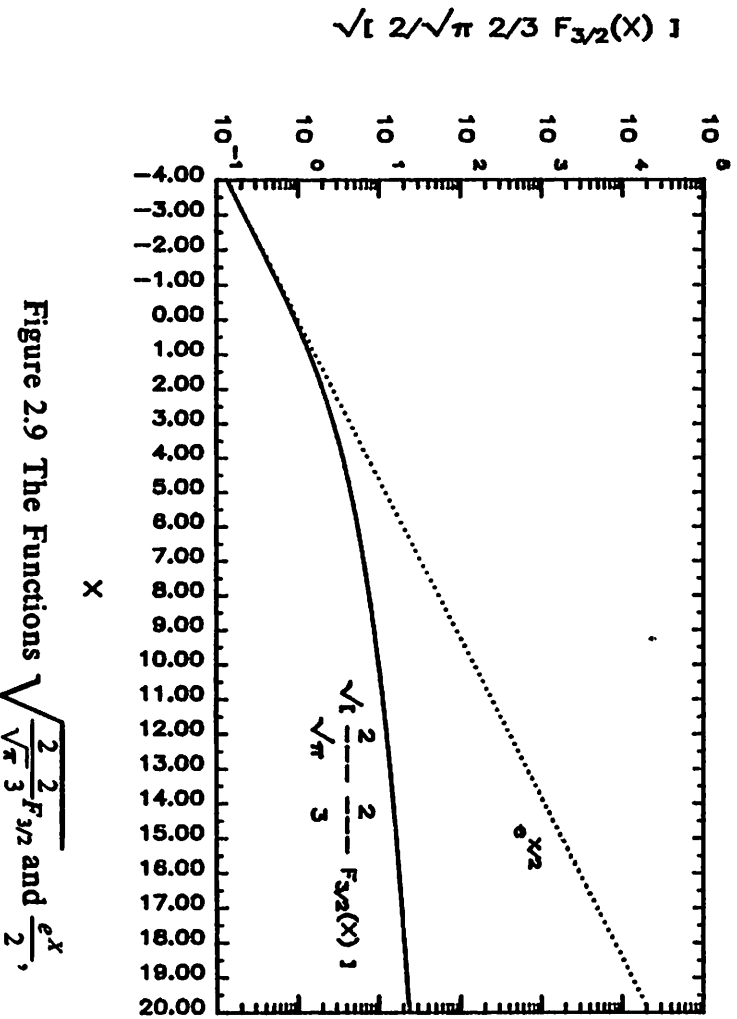
$$\int_0^{\phi_s} N(\phi) d\phi = \frac{kT}{q} N_C e^{E_F - E_C + q \frac{(\phi_s - \zeta_n)}{kT}} \quad (2.38)$$

Functions $\frac{2}{\sqrt{\pi}} F_{1/2}(x)$ and e^x , which are counterparts based upon Boltzmann and Fermi-Dirac statistics, are plotted together in Figure 2.8. The quantities $\sqrt{\frac{2}{\sqrt{\pi}} \frac{2}{3} F_{3/2}(x)}$ and $e^{\frac{x}{2}}$, which correspond to the inversion charge density Q_{INV} but are based upon different statistics, are plotted in Figure 2.9. $F_{1/2}$ and $F_{3/2}$ are calculated by the Table-Look-Up method based upon the McDougall-Stoner table [34]. The difference between the results based upon Fermi-Dirac and Boltzmann statistics increases to approximately ten percent as the Fermi level approaches the band edge.

The relationship between the surface potential and the gate voltage can be deduced from Equation (2.21) and the expression Q_{SI} as:

$$V_{GB} = \phi_s + \sqrt{\gamma^2 \phi_s + \frac{\gamma^2}{N_{SUB}} \int_0^{\phi_s} N(\phi) d\phi} \quad (2.39)$$

The onset voltage of degeneracy, V_{DEG} , can be defined as the gate voltage at which the Fermi level reaches the band edge. The onset voltage of degeneracy versus the oxide thickness is plotted in Figure 2.10 for cases of both



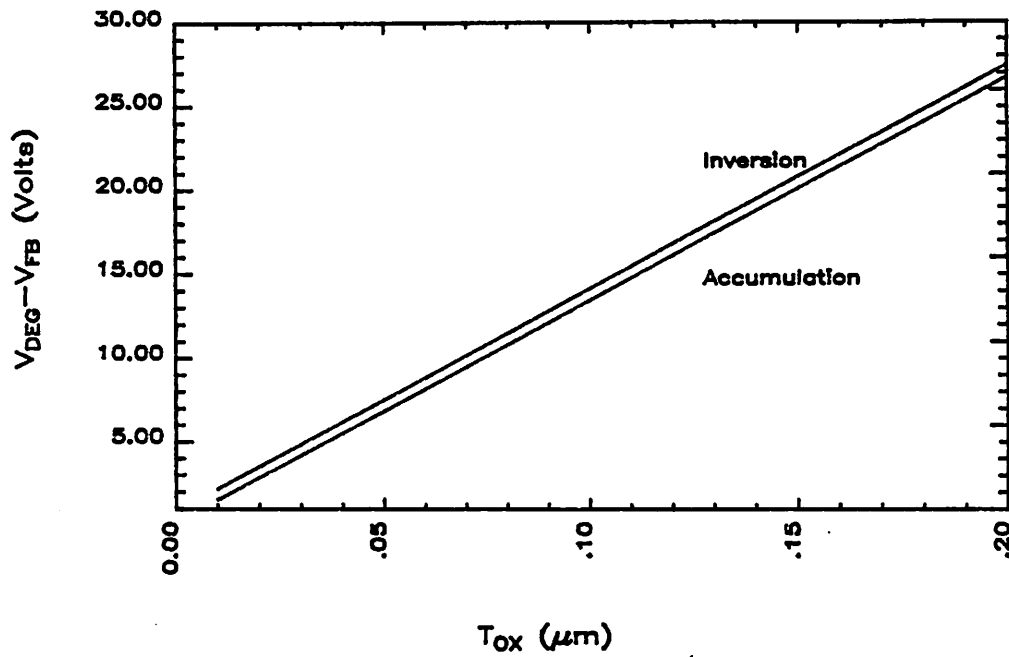


Figure 2.10 The Onset Voltage of Degeneracy as Defined by the Coincidence of the Fermi Level with Band Edge,

the inverted and accumulated surfaces.

An accumulated surface, e.g. the surface of a depletion device in the strong-conduction mode, differs from that of an inverted one because there is no depletion charge next to the interface. The degeneracy voltage of an accumulated surface is lower than that of an inverted surface as shown in Figure 2.10.

2.2.3. The Impact on Device Characteristics

By neglecting the surface-scattering effect which modulates the surface mobility, the drain conductance can be expressed as a function proportional to the carrier density per unit area, Q_{INV} , as in Equation (2.30):

$$G_{DS} = -\frac{W}{L}U_{EFF}Q_{INV}(drain)$$

where

$$Q_{INV}(drain) = C_{OX} [V_{GB} - V_{FB} - \phi_s] - Q_{DEP}(drain) \quad (2.40)$$

where V_{GS} , which is one order of magnitude larger than ϕ_s , dominates. Transconductance, G_M , can be expressed as:

$$G_M = \frac{W}{L}U_S \int_{\zeta_{n,S}}^{\zeta_{n,D}} \frac{\partial Q_{INV}}{\partial V_{GB}} d\zeta_n \quad (2.41)$$

$$= \frac{W}{L}U_S \int_{\zeta_{n,S}}^{\zeta_{n,D}} \frac{N(\phi_s - \zeta_n)}{Field_{SURF}(\zeta_n) + \frac{\rho_{SURF}(\zeta_n)}{C_{OX}}} d\zeta_n \quad (2.42)$$

It depends on the physical properties at the surface of the channel region. The impact of quantum-mechanical statistics on I_{DS} , G_{DS} and G_M is estimated by carrying out the related integrations in Equations (2.18), (2.30) and (2.42). The calculations in the degenerate condition is done by the Table-Look-Up method. The results show that, for the case of $T_{OX} = 0.01 \mu m$,

$N_{SUB} = 5 \times 10^{16} \text{cm}^{-3}$, $V_{TO} = 0.5$, $V_{DS} = 0.5$ and $V_{GS} \leq 10$ volts, the quantum-mechanical impact on these device characteristics is limited within 1 percent deviation from the classical one. This finding agrees with Reference [35] upon the capacitive calculation.

A differentiable and integratable empirical expression is fitted into func-

tion $F = \sqrt{\frac{2}{\sqrt{\pi}} \frac{2}{3} F_{3/2}}$:

$$F = e^{\frac{X}{2}} [a_0 + a_1 X + a_2 X^2] \quad (2.43)$$

where

$$a_0 = 0.924 \quad (2.44)$$

$$a_1 = -0.062 \quad (2.45)$$

$$a_2 = -0.012 \quad (2.46)$$

Its functional performance and percentage deviation are plotted in Figures 2.11 and 2.12.

A new relationship between the surface potential and the terminal voltages, which correctly reflects the impact of the quantum-mechanical effects, can be derived only by including the effects of the wave property and band quantization.

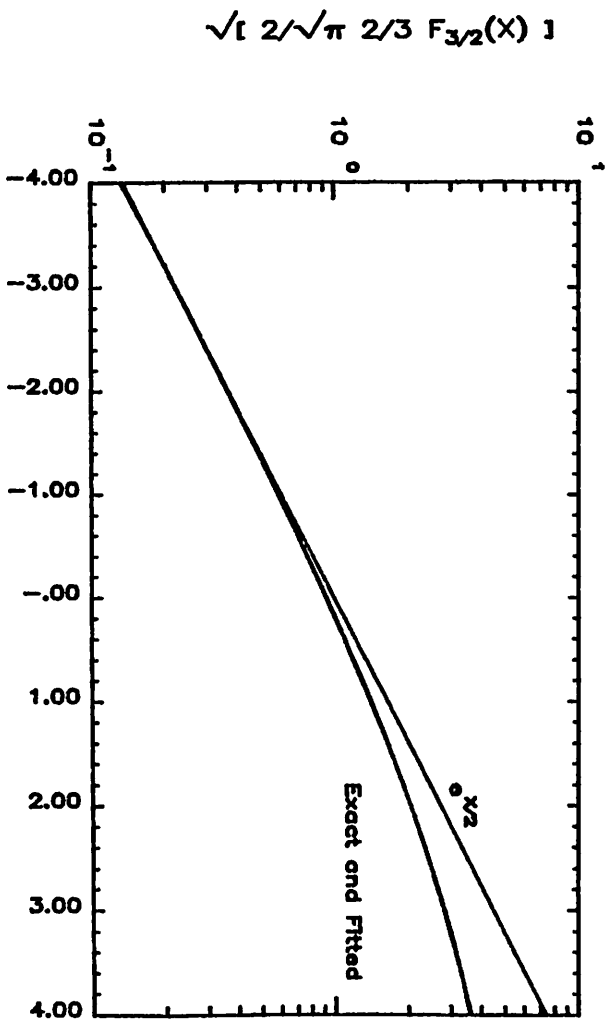


Figure 2.11 The Exact and Approximate Functional Curves of $\sqrt{\frac{2}{\sqrt{\pi}} F_{3/2}(X)}$,

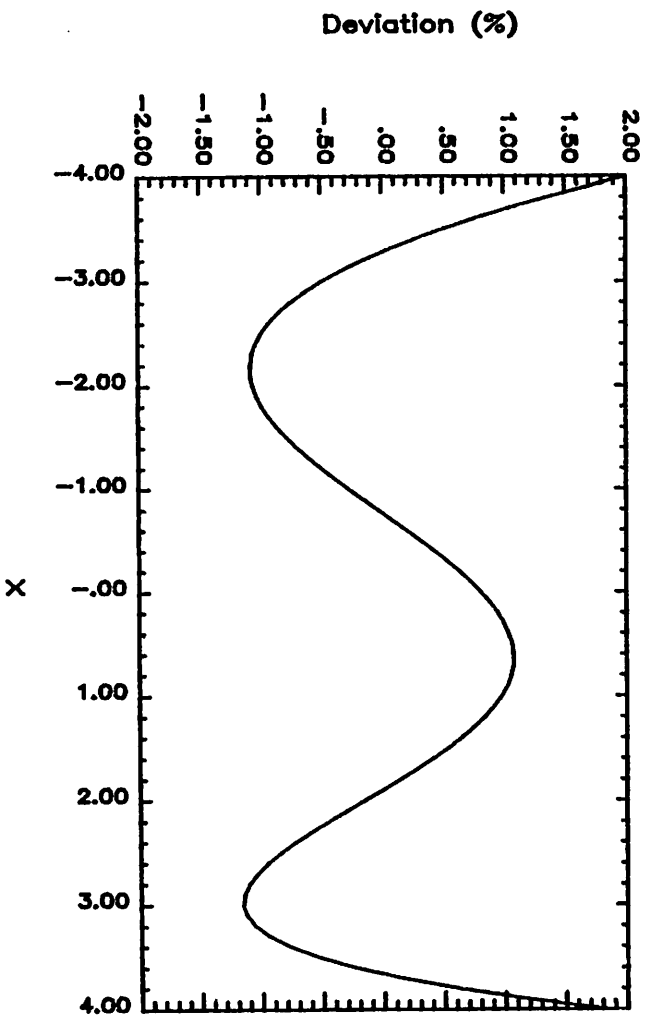


Figure 2.12 The Percentage Deviation between the Exact and Approximate Expressions of Function $\sqrt{\frac{2}{\sqrt{\pi}} F_{3/2}(X)}$,

CHAPTER 3

A Unified Approach to MOSFET Modeling

For today's MOSFET applications, an adequate CAD model, besides addressing the small-geometry effects, should also be able to simulate consistently the operations of both strong and weak inversions. Much of the literature on MOSFET modeling concentrates only on device characteristics either below or above the threshold voltage [31,36]. Some unified theories and models [17,21,26] have been proposed which require internal iterations to achieve a solution for the characteristics. These models have slow computational speed. Other models [15] attempt to join the characteristics based upon different theories of specific operational ranges. If the physical implications are not correctly perceived, these models will be accurate in only one of the two regions.

This chapter presents a unified approach to MOSFET modeling without invoking internal computational iterations. The proposed approach is based upon the recognition of the transition region between weak and strong inversions. It establishes an efficient CAD model covering overall characteristics. Section 3.1 describes the inadequacy of existing unified models. Sections 3.2 and 3.3 present the strong- and the weak-inversion models upon which the proposed model of transition region is based. Section 3.4 gives the definition and establishes the significance of the transition region. Model equations are developed. Section 3.5 describes the influence of fast-surface states. A comparison with existing unified models demonstrates the validity of the new model for CAD applications.

3.1. General Overview

The drain-to-source conduction of a MOSFET is induced and modulated by the gate voltage. The drain current consists of both diffusion and drift components. The diffusion current dominates in strong inversion, while the drift current dominates in weak inversion. In the previous chapter, the general expression of drain current, Equation (2.18), including both components, has been derived in terms of an integral relationship with the quasi-Fermi level as the integrating parameter:

$$\begin{aligned} I_{DS} &= -\frac{W}{L}U_{EFF} \int_0^{V_{DS}} Q_{INV} d\zeta_n \\ &= -\frac{W}{L}U_{EFF} \int_0^{V_{DS}} [Q_{SI} - Q_{DEP}] d\zeta_n \end{aligned} \quad (3.1)$$

In order to carry out the integration, the density of the total charge inside the semiconductor, Q_{SI} , has to be partitioned into the inversion charge Q_{INV} and the fixed surface depletion charge Q_{DEP} , and related to the terminal voltages.

The total semiconductor charge is balanced by the charge residing on the gate, and can be related to the terminal voltages, as derived in the previous chapter, by a manipulation of the Poisson equation, as in Equation (2.22):

$$\frac{1}{2} \left[\frac{Q_{SI}}{\epsilon_{si}} \right]^2 = \frac{qN_{SUB}}{\epsilon_{si}} Q_o \quad (3.2)$$

where

$$Q_o = \left[1 - e^{-\frac{2q\phi_F}{kT}} \right] \phi_s + \frac{kT}{q} e^{-\frac{q(2\phi_F + \zeta_n)}{kT}} \left[e^{\frac{q\phi_s}{kT}} - 1 \right] + \frac{kT}{q} \left[e^{-\frac{q\phi_s}{kT}} - 1 \right] \quad (3.3)$$

The difference between Equations (2.22) and (3.2) is in the inclusion of terms corresponding to the concentration of holes and depleted donors.

The diffusion current is proportional to the gradient of carrier density, while the drift current is proportional to the product of the carrier density and the electric field strength. In other words, these two current components are controlled by either the gradient or the magnitude of the surface potential, ϕ_s . Existing unified theories generally formulate the characteristic equations in terms of the surface potential which is a controlling variable in Equation (3.2).

The relationship between ϕ_s and the terminal voltages as predicted by Equation (3.2) is plotted in Figure 3.1 in which the ϕ_s -versus- V_{GS} curves are plotted with parameters ξ_n and V_{BS} . The curves asymptotically approach straight lines in the extreme of either strong or weak inversion. In these two extremes, the transcendental Equation (3.2) can be approximated by explicit analytical equations which can be used to develop the models of both regions.

Equation (3.2) is used by all the unified theories to relate the quasi-Fermi level to terminal voltages [17,21,26]. The approaches differ in the way they divide Q_{SI} into Q_{INV} and Q_{DEP} , thus leading to different results. In general, Equation (3.2) has to be solved by iteration, especially in the weak-inversion region where ϕ_s is almost constant over the entire integration domain of Equation (3.1). An accurate value of ϕ_s is required because the drain current is calculated as the difference between two very close quantities. Therefore, most unified theories require a well-converged solution of Equation (3.2) for the weak-inversion characteristics.

The unified model which is developed by Bacarani et al. [17], together with the model based upon the double integration [26], the conventional strong-inversion model [31] and the weak-inversion model by Swanson et al. [36] have been programmed on a Hewlett-Packard 1000 minicomputer to compare the computational speed (in second per operation), in linear,

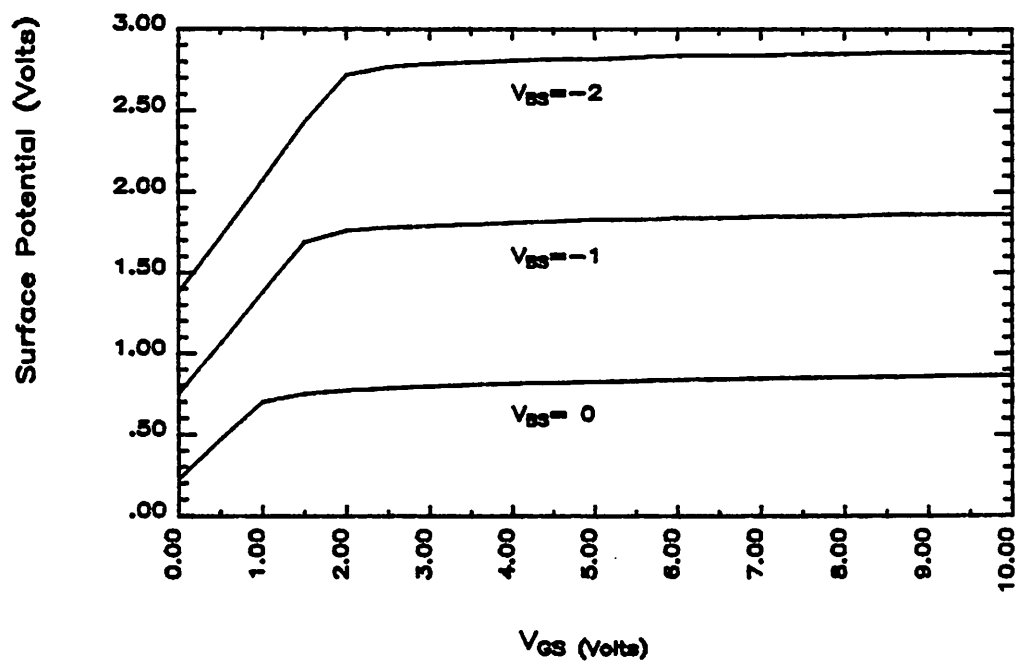
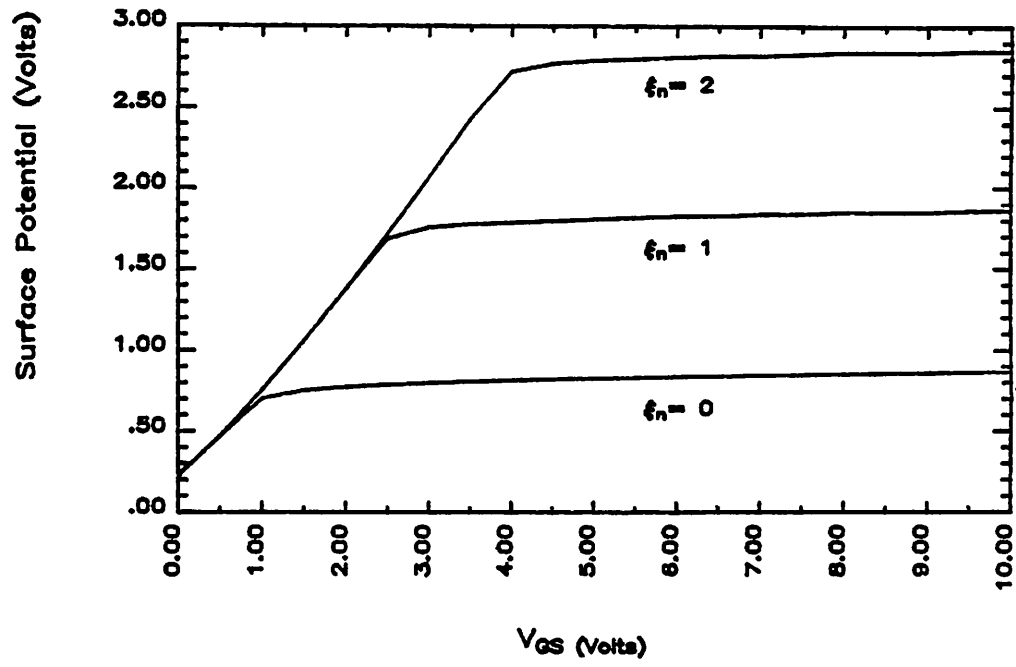


Figure 3.1 ϕ_s -versus- V_{GB} with Parameters ξ_n and V_{BS} ,

saturation, and weak-inversion regions. The results are summarized in Table 3.1:

Table 3.1			
Model	Linear	Saturation	Weak-Inv
P-S	5.23 sec/op	5.09 sec/op	5.22 sec/op
B-R-S	5.08 msec/op	3.03 msec/op	3.64 msec/op
Strong	0.85 msec/op	1.06 msec/op	-
Weak	-	-	0.68 msec/op

Table 3.1 Comparison of Computational Speeds

The computational speed of the iterative approach is three orders of magnitude greater than that of the double-integration approach, while that of the explicit approaches is five times as fast as the iterative approach. As the model evaluation consumes a very high percentage of computational time in VLSI circuit simulations, the explicit approach is much more desirable than the others.

The Pao-Sah theory [26] uses a rudimentary integral formulation,

$$I_{DS} = \frac{W}{L} U_{EFF} q \int_0^{v_{DS}} d\zeta_n \int_0^{\phi_s(\zeta_n)} \frac{N(\phi)}{E(\phi)} d\phi \quad (3.4)$$

where approximations are kept to a minimum. However, the result is cumbersome for CAD applications. The El-Mansy-Boothroyd theory [21] partitions the charge based upon overall weighting factors:

$$I_{DS} = \frac{W}{L} U_{EFF} \int_0^{v_{DS}} d\zeta_n \sigma_{INV} Q_{INV} \quad (3.5)$$

Although allowing for the influence of the spatial distribution, this treatment gives an unrealistic result because of using the weighted average. The Baccarani-Rudan-Spadini theory [17] decouples Q_{DEP} from Q_{INV} by relating Q_{DEP} to ϕ_s by a square-root relationship. It is equivalent to assuming that the inversion charge distribution has no influence on the potential distribution.

$$I_{DS} = \frac{W}{L} U_{EFF} C_{OX} \int_0^{V_{DS}} \left[V_{GB} - V_{FB} - \phi_s(\xi_n) - \gamma \sqrt{\phi_s(\xi_n)} \right] d\xi_n \quad (3.6)$$

This result agrees well with the Pao-Sah theory, especially in the weak-inversion region where the depletion charge dominates.

The other method of providing a model covering wide operational ranges is to attach exponential tails with measured weak-inversion slopes to the strong-inversion characteristics at a point slightly above the threshold voltage [15].

The threshold voltage used in model evaluation can be determined by:

- (a) plotting $\left(\frac{I_{DS}}{V_{DS}}\right)$ -versus- V_{GS} , measured at fixed low V_{DS} and fixed V_{BS} ,
- (b) extrapolating the linear portion of the curve to zero,
- (c) interpreting the interception on the V_{GS} axis, V_{GS}^o , as a point corresponding to pseudo zero inversion charge density,
- (d) relating V_{TH} to V_{GS}^o through the conventional current equation in a rearranged format:

$$V_{TH} = V_{GS}^o - \frac{V_{DS}}{2} - \frac{L \times I_{DS}}{W \times V_{DS} U_{EFF} C_{OX}} \quad (3.7)$$

The other parameters, N_{SUB} , ϕ_F , and γ , can be derived from the extrapolated V_{TH} 's at different V_{BS} 's:

$$N_{SUB} = \frac{[\gamma C_{OX}]^2}{2q \epsilon_s} \quad (3.8)$$

$$\phi_F = \frac{kT}{q} \ln \left[\frac{N_{SUB}}{N_I} \right] \quad (3.9)$$

$$\gamma = \frac{V_{TH}(V_{BS2}) - V_{TH}(V_{BS1})}{\sqrt{\phi_F - V_{BS2}} - \sqrt{\phi_F - V_{BS1}}} \quad (3.10)$$

Iterative computation is required to obtain a set of consistent parameters.

In order to compare the basic assumptions of different modeling approaches, the Pao-Sah theory is used to generate ideal characteristics; these characteristics are used to extract model parameters for the other models. The physical parameters used in the Pao-Sah model are listed in Table 3.2 together with the extrapolated parameters to be used for the other models:

Table 3.2						
Dev	Mdl -	NSUB (cm ⁻³)	TOX (μ m)	GAMMA (sqrt V)	VTO (V)	VFB (V)
No.1	Intr.	5.0E14	0.105	0.39	0.26	-0.57
	Extr.	3.1E14	0.105	0.36	0.41	-0.38
No.2	Intr.	5.0E15	0.105	1.24	0.26	-1.41
	Extr.	3.5E15	0.105	1.17	0.41	-1.19
No.3	Intr.	2.0E16	0.105	2.48	0.26	-2.95
	Extr.	1.9E16	0.105	2.41	0.42	-2.37
No.4	Intr.	5.0E15	0.05	0.59	0.26	-0.88
	Extr.	3.2E15	0.05	0.54	0.41	-0.68
No.5	Intr.	5.0E15	0.20	2.36	0.26	-2.32
	Extr.	3.7E15	0.20	2.30	0.42	-2.09

Table 3.2 Intrinsic and Extrapolated Parameters

The extrapolated parameter values differ from the intrinsic ones. The most significant difference is between the value of V_{TH} and the value of V_{FB} . Though the values differ by only about $0.2V$, the difference implies that the extrapolated V_{TH} does not correspond to a point at which ϕ_s equals $2\phi_F$ as generally assumed. If the same parameters are used in the companion weak-inversion tail of the joint model with a single break point, the quality of the weak-inversion model is sacrificed.

The ideal characteristics with intrinsic parameters based upon the Pao-Sah theory [26], the simple strong-inversion model [31] with extrapolated parameters, the simple weak-inversion model [36] with intrinsic parameters, and the strong-weak-inversion model with single break point [15] with extrapolated parameters are plotted together in Figure 3.2 in which V_{DS} equals 0.05 V and 5.0 V. The method of choosing a single break point fails to recognize the existence of a transition region where none of the specialized theories apply. It results in an erroneous prediction of the current in weak inversion if it is matched in strong inversion, and vice versa.

All the weak-inversion models apply to the weak-inversion region only, and all the strong-inversion models apply to the strong-inversion region only. A single break point approach is not sufficient to retain the accuracy in both original theories.

3.2. Strong-Inversion Region

Strong inversion is characterized by either a high V_{GS} or a low quasi-Fermi level. At this extreme, the right hand side of Equation (3.2) is dominated by the term of inversion charge and ϕ_s can be approximated as:

$$\begin{aligned}\phi_s &= 2\phi_F + \zeta_n + \frac{kT}{q} \ln \left[\frac{q}{kT} \left[\left[\frac{V_{GB} - \phi_s}{\gamma} \right]^2 - \phi_s \right] \right] \\ &= \phi_{BI} + \zeta_n\end{aligned}\quad (3.11)$$

where

$$\phi_{BI} = 2\phi_F + \frac{kT}{q} \ln \left[\frac{q}{kT} \left[\left[\frac{V_{GB} - \phi_s}{\gamma} \right]^2 - \phi_s \right] \right] \quad (3.12)$$

ϕ_s is linearly related to the quasi-Fermi level ζ_n and logarithmically related to V_{GB} . Its dependence on V_{GB} is small and ϕ_{BI} stays close to $2.5\phi_F$ in the

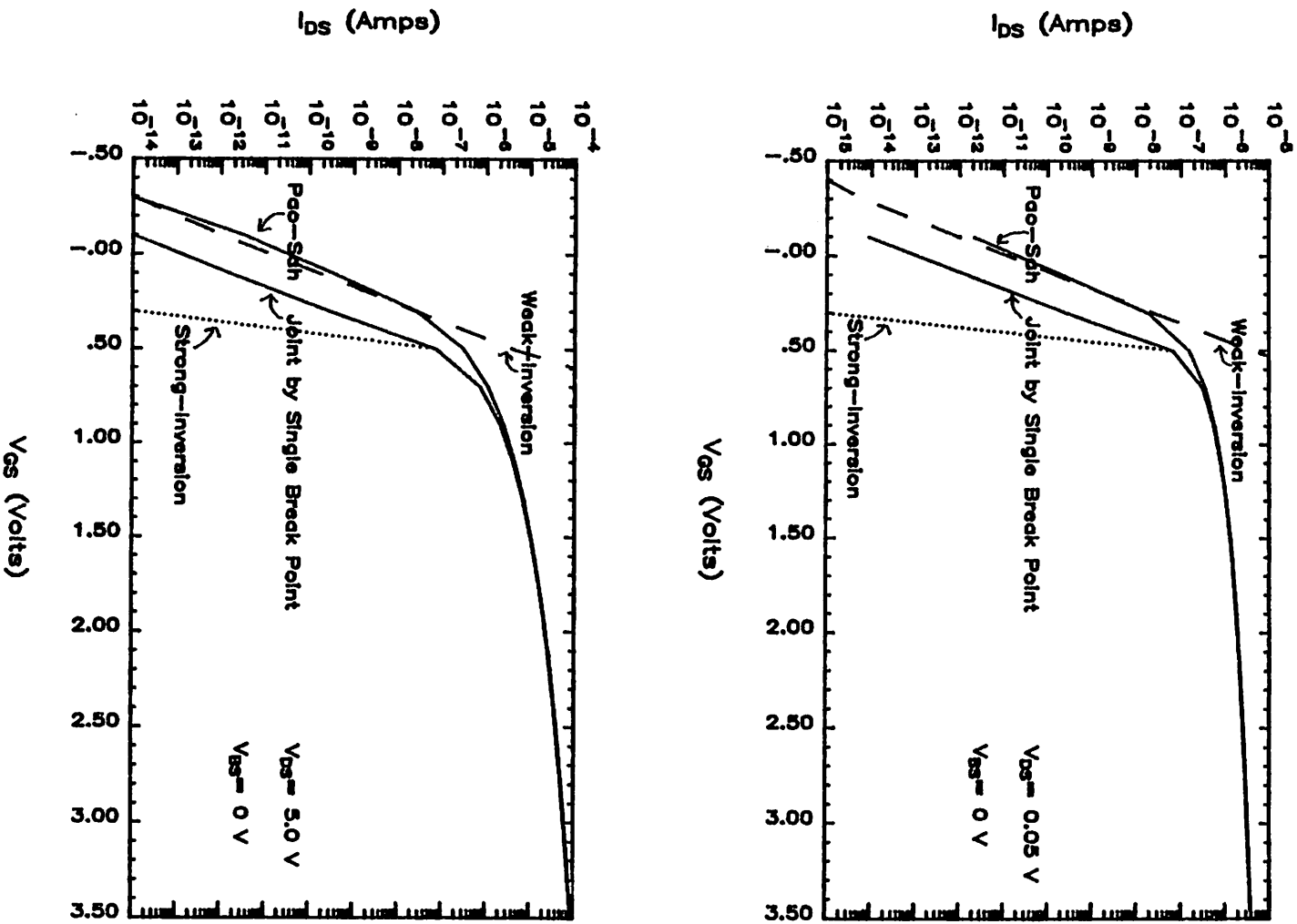


Figure 3.2 The Pao-Sah Model and the Approximations in Strong- and Weak-Inversion Regions at V_{DS} 0.05 V and 5.0 V,

strong-inversion region. Therefore the ϕ_s used inside the logarithm can be approximated by $(2.5\phi_F + \zeta_n)$ without losing accuracy.

As pointed out in the previous chapter, when V_{GB} is sufficiently high, Equation (3.2) no longer holds because the Boltzmann statistics can not apply to the degenerate case. A new equation is proposed in the previous chapter to replace Equation (3.2) in order to include quantum-mechanical-statistical effects. The break point joining the non-degenerate and degenerate cases is defined as follows:

$$V_{DEG} = V_{FB} + \phi_F + \frac{E_G}{2q} + \zeta_n \quad (3.13)$$

As concluded in the previous chapter, the correction factor due to degenerate statistics is small and it is important only at a very high V_{GS} . In most of the practical operational range, the device characteristics are subject to the strong influence of surface-mobility modulation. The degeneracy impact of sub-band splitting can be included in empirical equations designed for mobility modulation. Thus this effect is neglected in the following derivation of model equations.

The terms are plotted in Figure 3.3 for comparison. ϕ_s and the contribution of the depletion charge are approximately constant in the strong-inversion region. Q_{DEP} can be approximated as:

$$Q_{DEP} = \gamma C_{OX} \sqrt{\phi_s} \quad (3.14)$$

The current equation can be derived accordingly:

$$I_{DS} = \frac{W}{L} U_{EFF} C_{OX} I^o \quad (3.15)$$

where

$$I^o = \left[V_{GB} - V_{FB} - \frac{\phi_{s,D} + \phi_{s,S}}{2} \right] \left[\phi_{s,D} - \phi_{s,S} \right] - \frac{2}{3} \gamma \left[\phi_{s,D}^{\frac{3}{2}} - \phi_{s,S}^{\frac{3}{2}} \right] \quad (3.16)$$

This formulation is very similar to the conventional one [31] and the difference is minor.

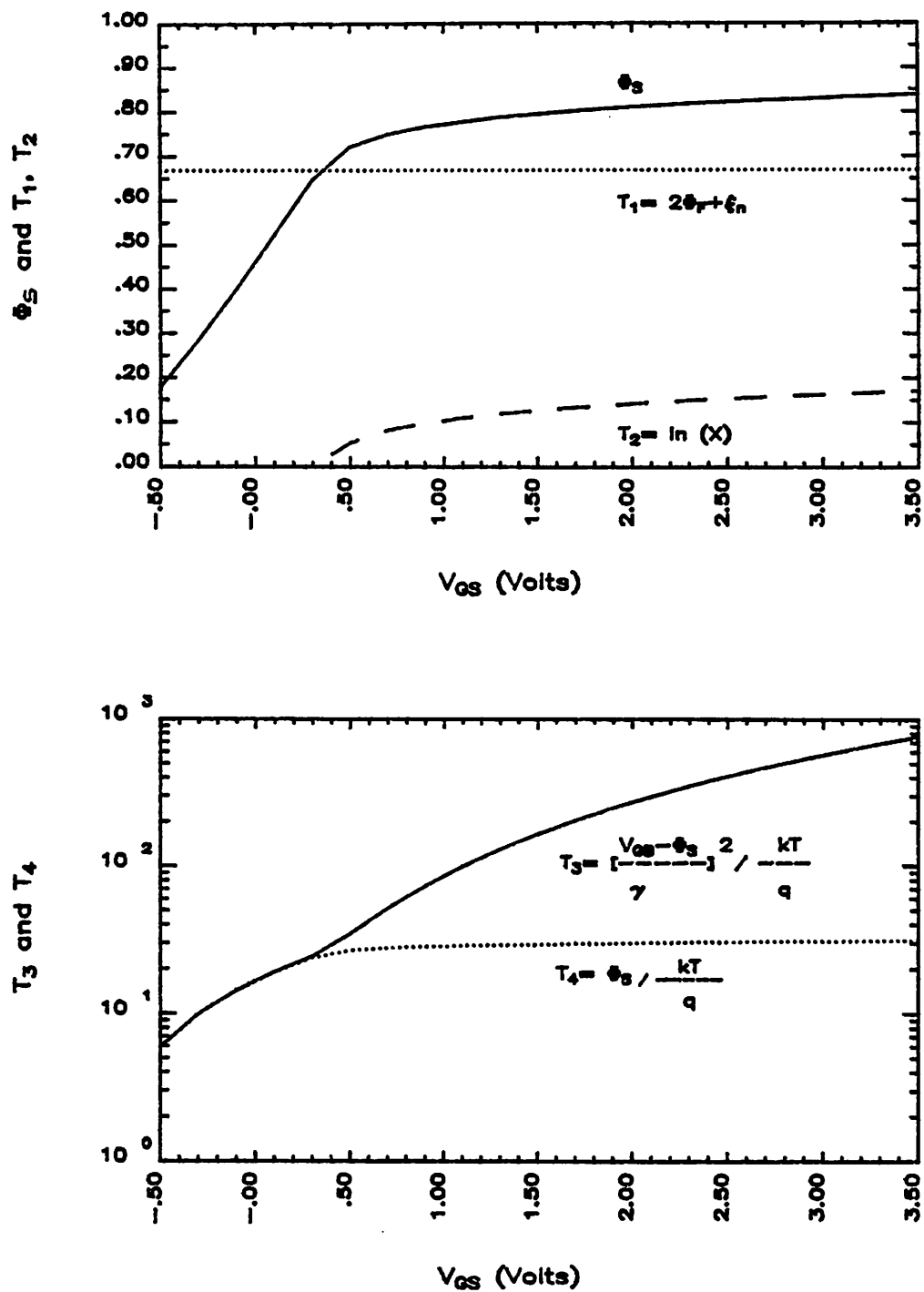


Figure 3.3 The Contributions to ϕ_s from Various Terms: T_1 , T_2 , T_3 , and T_4 ,

3.3. Weak-Inversion Region

When V_{GB} is low and/or the quasi-Fermi level, ζ_n , is high, ϕ_s is approximately linearly proportional to V_{GB} and very insensitive to the quasi-Fermi level, as illustrated in Figure 3.1. In Equation (3.2), the term corresponding to the minority carrier concentration in weak inversion, which depends on the quasi-Fermi level, is so small that it can be ignored. When ϕ_s is smaller than $(2\phi_F + \zeta_n)$ and the term of the minority carrier concentration is neglected in Equation (3.2), the expression ϕ_s becomes:

$$\phi_s = \frac{\gamma^2}{2} + V_{GB} + \gamma \sqrt{\frac{\gamma^2}{4} + V_{GB}} \quad (3.17)$$

This approximation fails at $\phi_s \geq (2\phi_F + \zeta_n)$ where the exponent of the minority carrier term in Equation (3.2) becomes positive and the magnitude of the term increases rapidly.

In the weak-inversion region, the depletion charge is dominant and can be expressed as:

$$Q_{DEP} = -\gamma C_{OX} \sqrt{\phi_s - \frac{kT}{q}} \quad (3.18)$$

and the total charge density inside the semiconductor can be approximated as:

$$Q_{SI} = \gamma C_{OX} \sqrt{\phi_s - \frac{kT}{q}} \left[1 + \frac{1}{2} \frac{kT/q}{\phi_s - kT/q} e^{\frac{q(\phi_s - \zeta_n - 2\phi_F)}{kT}} \right] \quad (3.19)$$

The density of the inversion charge equals the difference between the magnitudes of Q_{SI} and Q_{DEP} :

$$Q_{INV} = Q_{SI} - Q_{DEP} \quad (3.20)$$

$$= C_D \frac{kT}{q} e^{\frac{q(\phi_s - \zeta_n - 2\phi_F)}{kT}} \quad (3.21)$$

where

$$C_D = \sqrt{\frac{q \epsilon_{si} N_{SUB}}{2[\phi_s - kT/q]}} \quad (3.22)$$

The drain current is dominated by diffusion. The configuration of the channel region of a MOSFET in weak inversion and the base region of a bipolar transistor is similar. Accordingly, the weak-inversion current can be formulated as:

$$I_{DS} = WD \frac{Q_{SRC} - Q_{DRN}}{L} \quad (3.23)$$

$$= \frac{W}{L} U_S C_D \frac{kT^2}{q} e^{\frac{q(\phi_s - 2\phi_F - V_{SB})}{kT}} \left[1 - e^{-\frac{qV_{DS}}{kT}} \right] \quad (3.24)$$

3.4. Join Together

The weak-inversion model is accurate in the region where ϕ_s is equal to or less than $(2\phi_F + \zeta_n)$, while the strong-inversion model is good in the region where the inversion charge is the dominant charge component. By properly defining the transition region where neither of these two models is valid, the characteristics in the weak- and strong-inversion regions are joined together through an empirical transition characteristics to provide an accurate and efficient CAD model over the overall operational range.

The approximated ϕ_s of both strong and weak inversions is plotted in Figure 3.4, together with the exact solution, over the range of $(V_{GB} - V_{2\phi_F})$ between -1 and +4 volts. $V_{2\phi_F}$ is the gate voltage at which the surface potential equals $(2\phi_F + \zeta_n)$. The boundaries of the transition region can be defined as follows:

(a) weak-inversion boundary: V_{weak} where surface potential

$$\phi_{s,WEAK} = (2\phi_F + \zeta_n); \text{ This is equivalent to the condition } \frac{\partial Q_{INV}}{\partial \phi_s} = \frac{\partial Q_{DEP}}{\partial \phi_s}$$

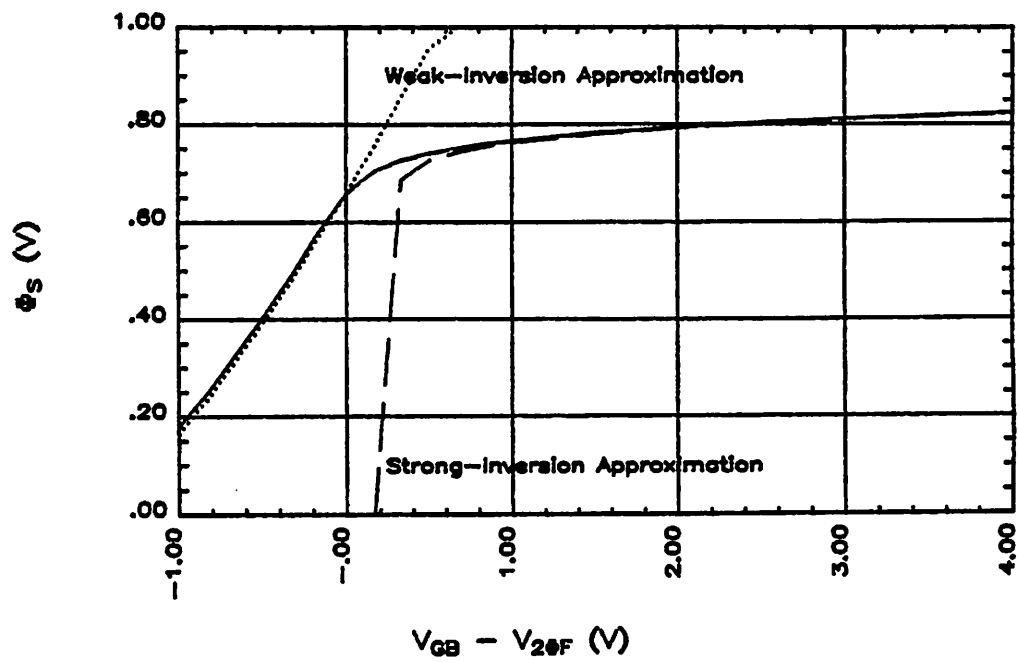


Figure 3.4 The Approximate and Exact ϕ_s in Strong- and Weak-Inversion Regions,

[37]. In other words, in this condition, a variation of ϕ_s induces the same amount of both the inversion and depletion charges. As indicated in the previous section, once ϕ_s is greater than $(2\phi_F + \zeta_n)$, the inversion charge increases exponentially and the depletion charge is no longer the dominant factor in determining the surface potential.

- (b) strong-inversion boundary: V_{strong} where the surface potential is $\phi_{s,STRONG}$ so that the contribution to ϕ_s from Q_{INV} , $\phi_{s,INV}$ is ten times greater than that from Q_{DEP} , $\phi_{s,DEP}$. $\phi_{s,INV}$ and $\phi_{s,DEP}$ are the first and third terms inside the square root at the right side of Equation (3.2):

$$\phi_{s,INV} = \frac{kT}{q} e^{\frac{q(\phi_s - 2\phi_F - \zeta_n)}{kT}} \quad (3.25)$$

$$\phi_{s,DEP} = \phi_s \quad (3.26)$$

By assigning $X = \frac{\phi_{s,INV}}{\phi_{s,DEP}}$, it is reduced to:

$$\phi_{s,STRONG} = 2\phi_F + V_{SB} + \frac{kT}{q} \ln\left(X \frac{q\phi_{s,STRONG}}{kT}\right) \quad (3.27)$$

The corresponding gate voltage, V_{STRONG} , is:

$$V_{STRONG} = V_{FB} + \phi_{s,STRONG} + \gamma\sqrt{(1+X)\phi_{s,STRONG}} \quad (3.28)$$

$\phi_{s,STRONG}$ can be estimated by replacing the $\phi_{s,STRONG}$ inside the logarithm by $(2\phi_F + \zeta_n)$.

Inside the transition region, the sensitivity of ϕ_s -versus- V_{GB} , $(\partial\phi_s/\partial V_{GS})(V_{GB} - V_{FB})/\phi_s$, changes from greater than one percent to about ten percent. The following expression is proposed to approximate the relationship of ϕ_s to V_{GS} in the transition region:

$$\phi_s = a + b(V_{GB} - V_{WEAK})^n \quad (3.29)$$

Once the exponent n , the sensitivity coefficient, is determined, the coefficients a and b can be deduced from the boundary conditions. n can best be approximated as $\frac{1}{2}$ to reflect the average sensitivity within the transi-

tion region. For cases of $5.0 \times 10^{14} \leq N_{SUB} \leq 5.0 \times 10^{16}$ and $0.05 \mu m \leq T_{OX} \leq 0.2 \mu m$, the difference between V_{WEAK} and V_{STRONG} is approximately $0.6V$. The resultant ϕ_s , together with the exact solution and the percentage deviation are plotted in Figure 3.5 for comparison. The deviation between the approximation and the exact solution is less than 10 percent.

The relationship of V_{GB} to the logarithm of drain currents is very similar to that of ϕ_s -versus- V_{GB} . The formulation of the drain current in the transition region is complicated by the dependence of ϕ_s on the quasi-Fermi level ζ_n which is the integrating variable in the current equation. Instead of dividing the integral into three parts, which corresponds to partitioning the channel into strong-, weak-inversion and transition regions, the weak- and strong-inversion characteristics are joined through the same transition region by a similar equation. The comparisons between the current-voltage characteristics based upon different approaches, at $V_{DS} = 0.05V$ and $V_{BS} = 0V$, are plotted in Figure 3.6 with parameters N_{SUB} and T_{OX} . The transition region is about the same as the one in the relationship between ϕ_s -versus- V_{GB} . The drain current in the transition region is expressed in terms of the currents at the break points.

$$I_{DS} = e^{\ln(I_{WEAK}) + b(V_{GB} - V_{WEAK})^{\frac{1}{2}}} \quad (3.30)$$

where

$$b = \frac{\ln(I_{STRONG}) - \ln(I_{WEAK})}{(V_{STRONG} - V_{WEAK})^{\frac{1}{2}}} \quad (3.31)$$

Compared with the exact ideal characteristics in Figure 3.7, the overall agreement between the exact and joint solutions is good. The computational speed of this model is as fast as that of simple models in both weak- and strong-inversion regions. Only in the transition region is there a penalty in computational speed.

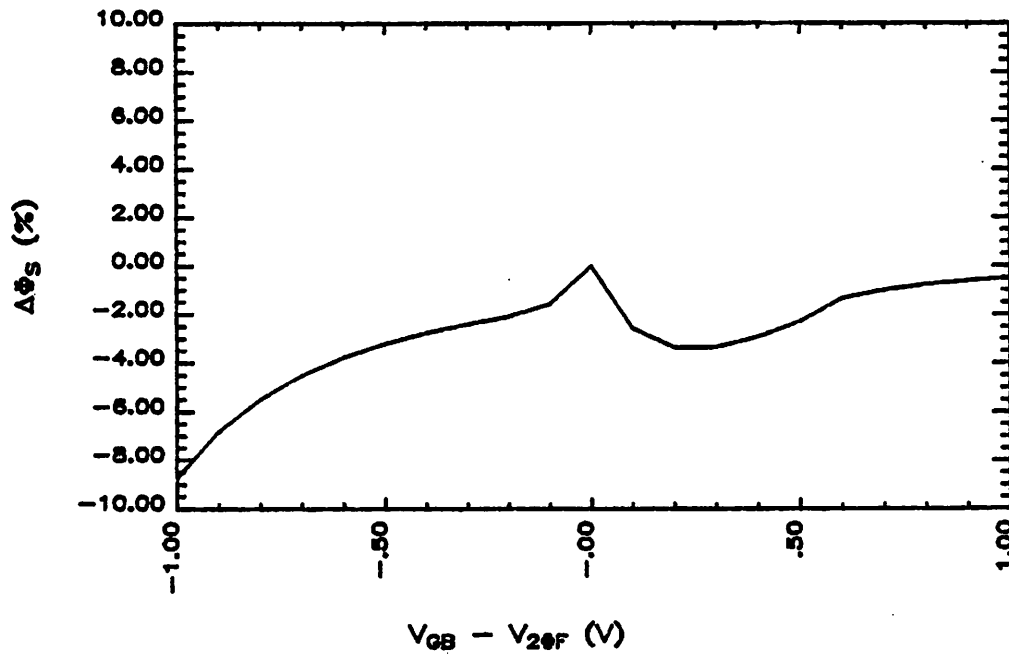
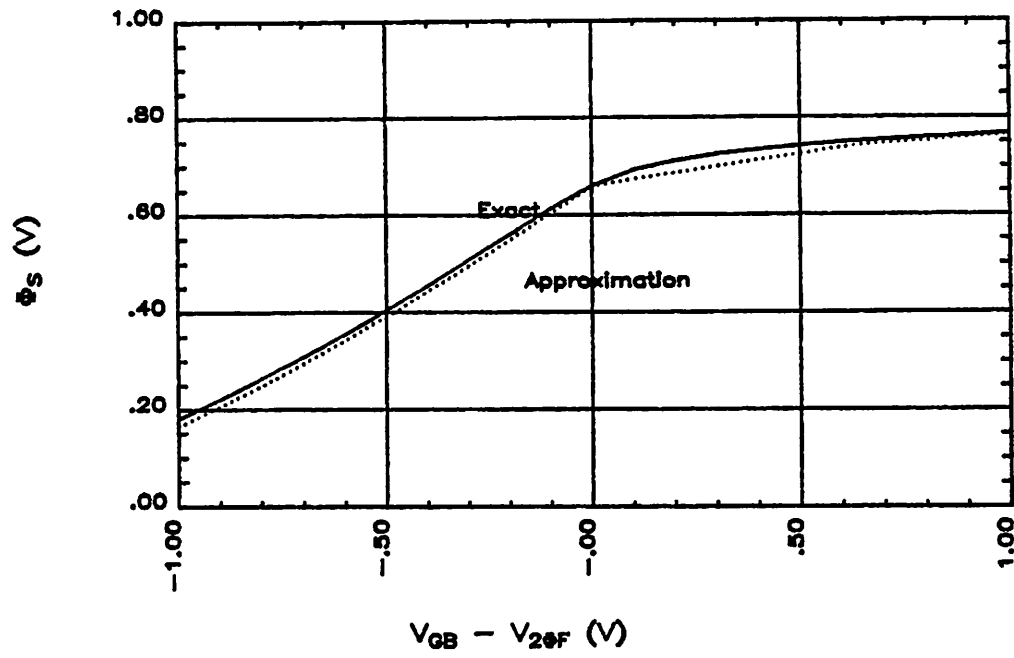


Figure 3.5 The Exact and Joint Curves of ϕ_s -versus- V_{GB} and the Percentage Deviation,

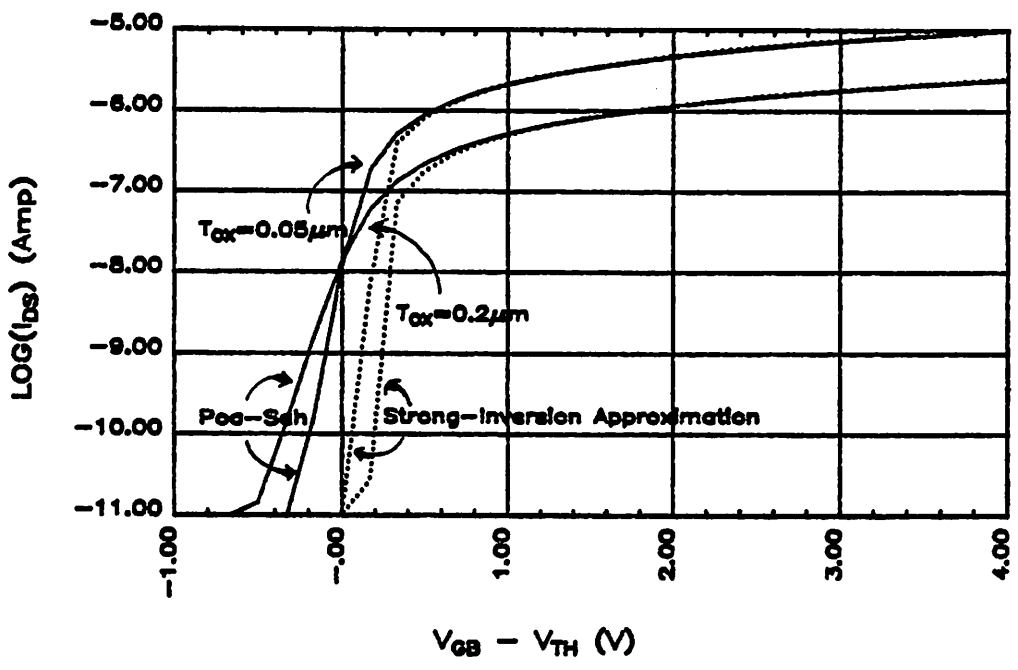
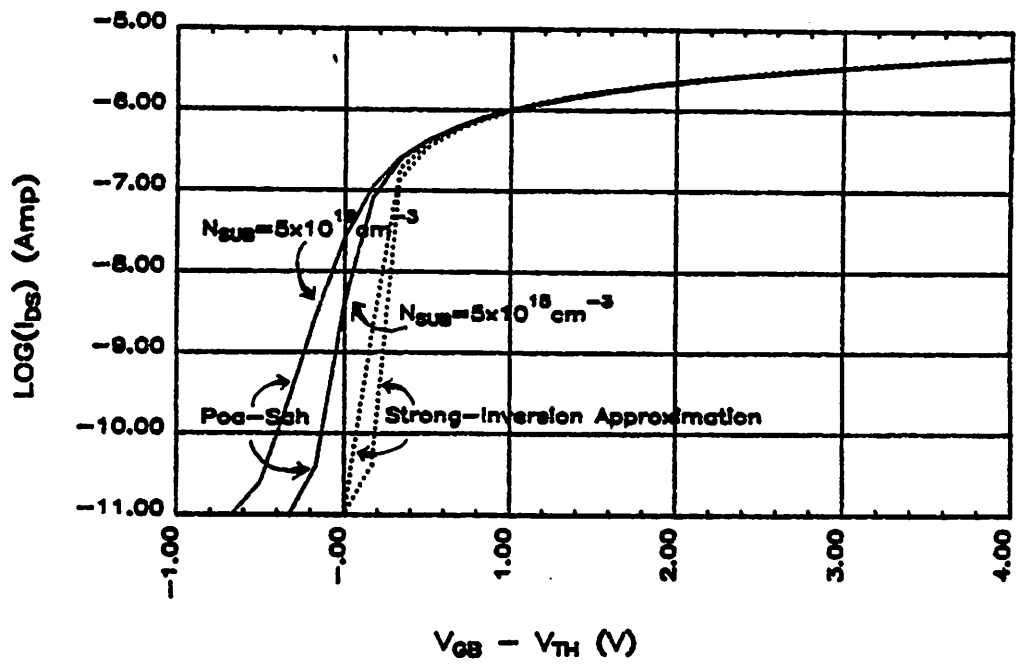


Figure 3.6 The Exact and Approximate Curves of I_{DS} -versus- V_{GS} in Strong-inversion Regions with Parameters N_{SUB} and T_{OX} .

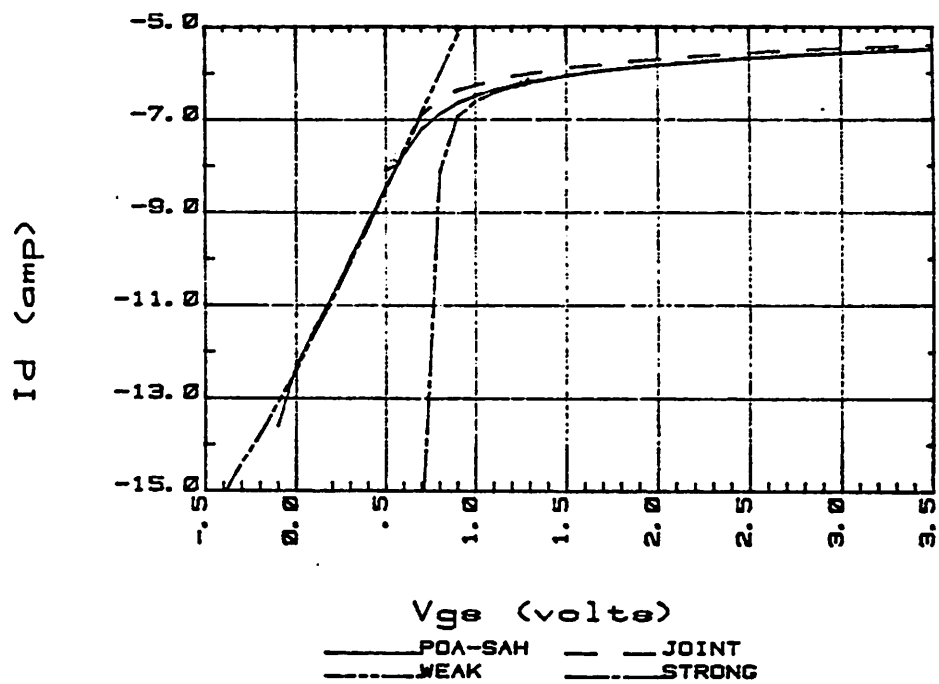


Figure 3.7 The Exact and Joint Curves of I_{DS} -versus- V_{GB} ,

3.5. The Influence of Fast-Surface States

The fast-surface-state density is used by van Overstraeten et al. [38] and Swanson et al. [36] as a parameter to characterize the weak-inversion region. Fast-surface states are the surface states whose lifetime is so short as to be filled and/or emptied fast enough to follow the variation in ϕ_s , induced by changes in the applied biases. The fast-surface states are induced by the broken bonds at the surface resulting from the interruption of the crystalline structure [39]. They distribute themselves almost uniformly over the center of the energy gap, with the peak densities near the band edges. The detailed distribution function differs from material to material. Experiments [40] show that the density of fast-surface states is about 10^{10} to $10^{11} \text{ cm}^{-2} \text{ eV}^{-1}$ in the central region.

In the presence of fast-surface states, the Q_{SI} in the left side of Equation (3.2) becomes:

$$Q_{SI} = C_{OX} \left[V_{GB} - V_{FB} - \phi_s + \frac{qN_{FS}}{C_{OX}} [\phi_s - \xi_n] \right] \quad (3.32)$$

Figure 3.8 shows how the relationships of ϕ_s -versus- V_{GB} and I_{DS} -versus- V_{GB} vary with the fast-surface-state density. Both relationships are based upon the Pao-Sah theory with Q_{SI} defined by Equation (3.32).

The presence of fast-surface states widens the transition region and lowers the current. This situation is equivalent to lower the threshold voltage. If the fast-surface-state density is abnormally high, say 10^{12} , the turn-on characteristics are softened and the weak-inversion slope is reduced. Fast-surface states have a significant effect only in the weak-inversion region. The approximated ϕ_s in the weak-inversion region is updated to include the effect of fast-surface states:

VDS=0.05, VTO=0.26

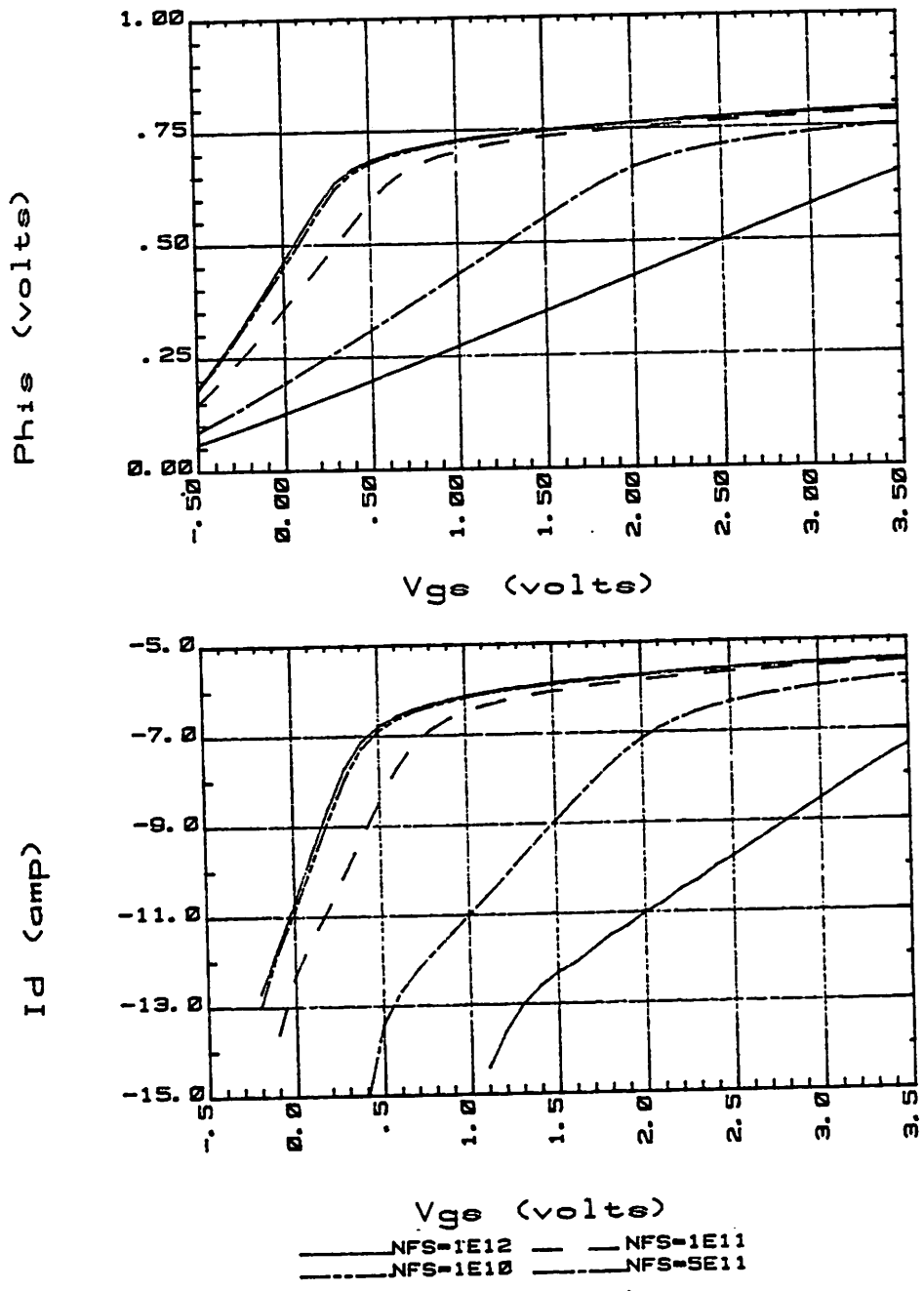


Figure 3.8 The Curves of ϕ_s -versus- V_{GB} and I_{DS} -versus- V_{GB} with Parameter N_{FS} ,

$$\phi_s = \frac{V_{GB} - V_{FB}}{1 + \alpha} + \frac{1}{2} \left[\frac{\gamma}{1 + \alpha} \right]^2 - \frac{\gamma}{1 + \alpha} \sqrt{\frac{1}{4} \left(\frac{\gamma}{1 + \alpha} \right)^2 + \frac{V_{GB} - V_{FB}}{1 + \alpha}} \quad (3.33)$$

where

$$\alpha = \frac{qN_{FS}}{C_{OX}} \quad (3.34)$$

The current equation in weak inversion is modified accordingly. The weak-inversion slope, $\frac{kT}{q} \frac{\partial \ln(I_{DS})}{\partial V_{GB}}$, becomes:

$$\frac{kT}{q} \frac{\partial \ln(I_{DS})}{\partial V_{GB}} = \frac{1}{1 + \alpha} \left[1 - \frac{1}{\sqrt{1 + 4 \left(V_{GB} - V_{FB} \right) \frac{1 + \alpha}{\gamma^2}}} \right] \quad (3.35)$$

The emphasis in this chapter is placed upon the transition between the strong- and weak-inversion regions, i.e. the region close to the threshold voltage. The device characteristics are better described by the flatband voltage, V_{FB} , than by the threshold voltage, V_{TH} . Once the device operates in the strong-inversion region, the effect of surface-mobility modulation, which is not covered in this chapter, can not be ignored and will be presented in Chapter 6.

CHAPTER 4

Two-Dimensional Simulations of Small-Geometry MOSFETs

With decreasing transistor dimensions, it has become more difficult to describe MOS transistors with equations that are simple enough for hand calculations or programmable calculators and yet retain sufficient accuracy to provide useful information about the device characteristics. In a small-geometry MOSFET both the impurity and potential distributions are extremely inhomogeneous. The numerical solution of two-dimensional potential and current-continuity equations is required to determine their characteristics. A thorough solution including every possible effect can be obtained using maxi-computers.

However, a more limited computer program with interactive capacity is also needed. Such a program, if sufficiently fast and efficient, can interactively provide iterative solutions which can then be used to obtain the optimal device structure. This requirement limits the solutions to that of the two-dimensional impurity and potential distributions, in other words, to the handling of the weak-inversion or weak-injection approximation for an MOS transistor. Since VLSI devices are geared toward low-voltage and low-power applications, these characteristics are of critical importance.

Program TWIST (Two-dimensional Interactive Simulation of MOS Transistors) has been developed using a minicomputer together with graphics terminals to simulate the characteristics of weak inversion and weak-injection punchthrough by the solution of the two-dimensional Poisson equation. Graded mesh, modified Gummel's algorithm, and Successive-Over-Relaxation iteration, together with a by-pass scheme, are implemented. The desired high-speed interactive feature and the graphics representation of all

data are demonstrated. Program TWIST is used in later chapters to study the weak inversion and weak-injection punchthrough characteristics.

The use of this program allows optimized device structures to be developed which then deserve more elaborate simulations involving the complete solution of both the potential and the transport aspects, which presently consumes approximately 50 times more computational time than the approach presented here. In a working hierarchy of CAD tools, structural and impurity parameters can be obtained from process simulators [41-42]. TWIST can then be used to optimize and develop semi-empirical models of small-geometry devices. At that point, a full two-dimensional potential and current-continuity solution would be justified [43] for the derivation of device parameters suitable for circuit-oriented simulators [11-13].

Section 4.1 gives an overview of the structure of Program TWIST. Section 4.2 describes the generation of impurity profiles and graded meshes on which the analysis can be based. Section 4.3 presents the basic physical equations and the boundary conditions used in the program. Section 4.6 describes the iteration algorithm used to solve the Poisson equation, and evaluates its performance. Section 4.7 presents the equations used to characterize devices from the self-consistent potential solution. The TWIST user's guide is presented in Appendix A, an example input together with its SUPREM input in Appendix B, the corresponding console record in Appendix C, and the program list in Appendix E.

4.1. Overview of Program TWIST

Program TWIST requires 65K 16-bit words on a Hewlett-Packard 1000 F-series computer. 32K words are used by the EMA (Extended Memory Area) to handle the data arrays. The present setup of the system is shown in Figure 4.1. The HP2648A graphics terminal provides interactive communication and graphics displays of the simulation results. These results can also be drawn on the four-color plotter HP9872A and/or a graphics hard copy unit.

The following device structures can be handled:

- (a) conventional MOSFETs with uniform substrates,
- (b) enhancement and depletion MOSFETs with single or double channel implants,
- (c) MOSFETs with asymmetric channel implants

The oxide covering the device to be simulated does not need to be uniform in thickness. The gate electrode can be arbitrarily located. The widths of the source and drain regions may differ.

Figure 4.2 shows the flowchart of Program TWIST. The program is divided into eight parts, the root and seven segments. The root, TWIST, is the executive program which controls the overall function. The first segment, GETPA, reads in data either from the console interactively or from a pre-defined file. The second segment, SETPA, initializes both the impurity distribution and the graded mesh, and preprocess the parameters to be used in the analysis. The third segment, SOLVE, iterates the Poisson equation using the finite-difference method at the given bias; the resolution and the accuracy can be controlled interactively. From the fourth through seventh

Figure 4.1 The System Block Diagram,

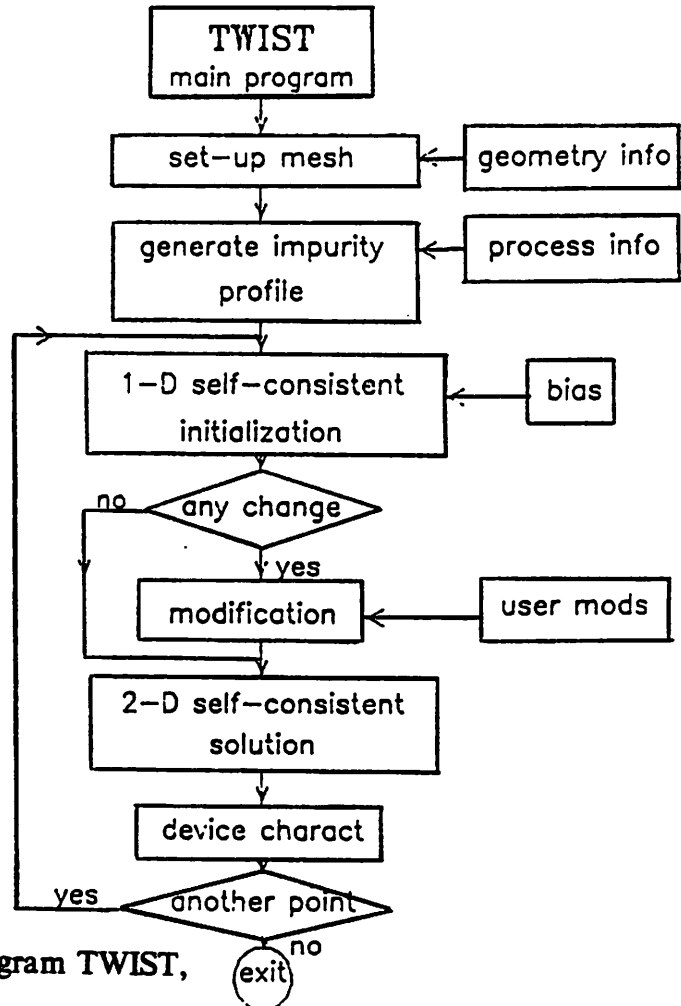
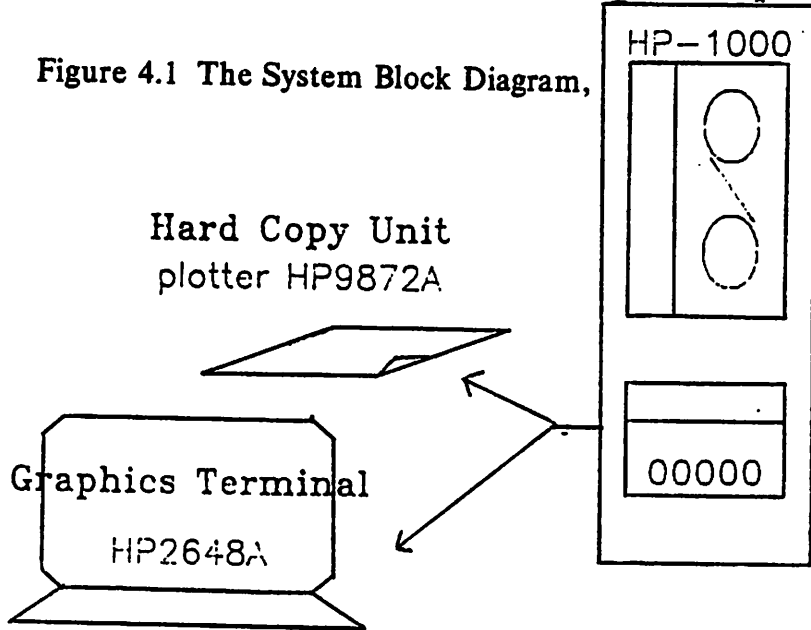


Figure 4.2 The Flow Chart of Program TWIST,

segments, OUTP1, OUTP2, OUTP3 and OUTP4, handle the graphics and numerical outputs; both can also be routed to hard copy units, i.e. either the plotter or the line printer.

4.2. Graded Mesh and Impurity Distribution

In a small-geometry MOSFET, both the potential and impurity distributions are extremely inhomogeneous. Large gradients exist in the immediate vicinity of the source and drain junctions and of the interface between oxide and silicon. In these regions, the density of the grid points on which the finite-difference equations are based should be high to ensure accuracy. The point density in the remote regions can be relatively low. For the mesh-setup purpose, the horizontal cross section of the device is divided into three regions: source, channel and drain, to which Mock's algorithm [19] is applied. The Y-constant in Mock's equation is changed to 0.05 to get reasonable mesh sizes in the surface region. A typical mesh layout is shown in Figure 4.3.

Up to three ion-implantation steps can be used to tailor the impurity profile. The first implant always covers the whole device as either the well implant of the CMOS/DMOS process or the threshold voltage implant of the NMOS process. The second one may cover only part of the device as required by the DMOS process, or the whole device as the threshold voltage implant of the CMOS process, the double implant of the NMOS process to suppress the source-to-drain punchthrough, and/or the depletion implant of the depletion-NMOS process. The third implant is the source/drain implant; it is allocated to the user-defined source/drain regions.

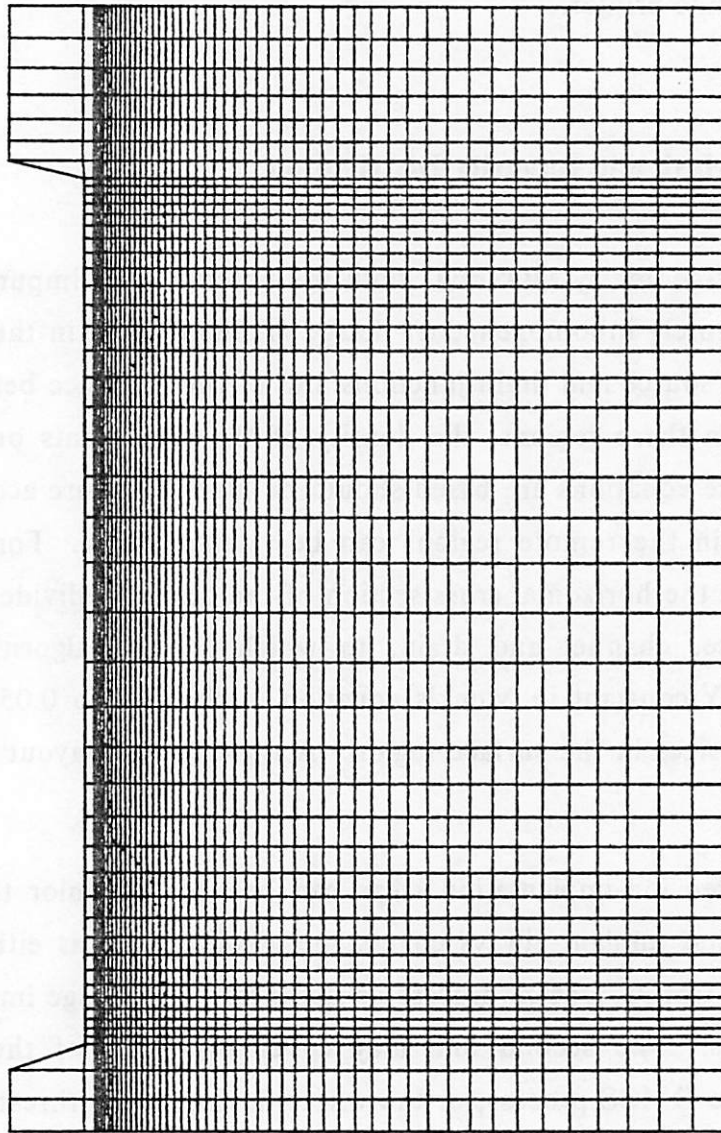


Figure 4.3 The Mesh Setup of Program TWIST,

The impurity profile generation can be either analytical or numerical. In the analytical mode, the ion-implantation profile assumes a Gaussian distribution. The two-dimensional redistribution, due to later high-temperature-process steps, is included. The expression used is [44-45]:

$$N(x,y,t) = \frac{Dose}{2\sqrt{\pi A}} \left[\Omega(y,t) + \Omega(-y,t) \right] \times \left[1 - erf \left[\frac{x - x_J}{\sqrt{4Dt}} \right] \right] \quad (4.1)$$

where

$$\Omega(y,t) = e^{-\frac{(y - R_p)^2}{A}} \left[1 + erf \left[B + Cy \right] \right] \quad (4.2)$$

The coefficients A, B and C are:

$$A = 2\Delta R_p^2 + 4Dt \quad (4.3)$$

$$B = \frac{R_p}{\Delta R_p} \left[\frac{2Dt}{A} \right]^{\frac{1}{2}} \quad (4.4)$$

$$C = \frac{\Delta R_p}{2\sqrt{DtA}} \quad (4.5)$$

The error function in the expression is evaluated by its polynomial approximation [46].

In the numerical mode, Equation (4.2) is replaced by the one-dimensional linear interpolation of the output from Program SUPREM [41]; the lateral two-dimensional redistribution is still based upon Equation (4.1); the standard deviation is estimated from the SUPREM result.

4.3. Basic Equations and Boundary Conditions

Under weak-inversion and/or weak-injection conditions, the equations of the current continuity and the electron-hole-recombination effect are ignored. The equations used to describe the physical mechanism inside the semiconductor are:

$$\nabla^2 \phi = -\frac{q}{\epsilon_{si}} [N_D - N_A + P - N] \quad (4.6)$$

$$N = \frac{N_I^2}{N_{SUB}} e^{\frac{q(\phi - \phi_{FN})}{kT}} \quad (4.7)$$

$$P = N_{SUB} e^{-\frac{q(\phi - \phi_{FP})}{kT}} \quad (4.8)$$

The first one is the Poisson equation of potential ϕ . The last two are the electron and hole densities based upon Boltzmann statistics. The variables ϕ_{FN} and ϕ_{FP} are the quasi-Fermi levels of electrons and holes, respectively.

The interior of the oxide is assumed to be free of charges. The Laplace form of the Poisson equation is used to describe the oxide potential distribution:

$$\nabla^2 \phi = 0 \quad (4.9)$$

The potential in the neutral substrate, the reference potential, is assigned zero. The potentials in the neutral source and drain regions are:

$$\phi(\text{src/drn}) = \frac{kT}{q} \ln \left[\frac{N(x,y)}{N_A} \right] + V_{APP} \quad (4.10)$$

where V_{APP} is the reverse bias voltage applied across the source/drain to the substrate junction.

Figure 4.4 is the cross section of a device with specified boundary conditions. The potentials at the two boundary planes at the left and right are determined by the self-consistent solution of the one-dimensional Poisson equation:

$$\nabla_y^2 \phi = -\frac{q}{\epsilon_{si}} [N_D - N_A + P - N] \quad (4.11)$$

The boundary potentials at points A and B are calculated by Equation (4.10), i.e. they are neutral. The boundary potentials at points C and D may be zero, i.e. neutral, or be extrapolated from the potential of their neighbors based upon the quadratic equation:

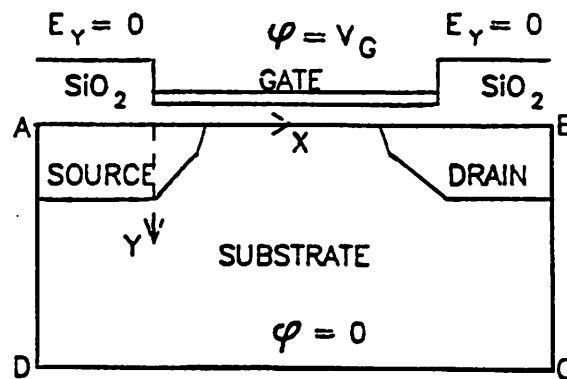


Figure 4.4 The Boundary Conditions of Program TWIST,

$$\phi_o = \frac{qN_{SUB}}{2\epsilon_{st}} [W_o - D_{y_o}]^2 \quad (4.12)$$

where W_o is the width of the depletion region to be sustained by the potential, ϕ_1 , at the neighboring grid point:

$$W_o = \sqrt{\frac{2\epsilon_{st}\phi_1}{qN_{SUB}}} \quad (4.13)$$

D_{y_o} is the mesh size at point C/D. This equation is based upon the assumption of complete depletion together with a zero electrical field in the horizontal direction.

The lower boundary plane is treated in the same way as that for points C and D which has been described. The mesh points in the lower boundary plane are either in the neutral substrate where the potential is zero, or in the completely-depletion region where the potential will be calculated from Equation (4.12).

The top boundary plane consists of the gate electrode and the exposed oxide. The potential at the gate electrode is the gate voltage. The boundary at the exposed oxide serves as a reflection plane of the potential distribution. This is equivalent to assume zero normal electrical fields at the surface, i.e. no charge on the exposed oxide.

4.4. Quasi-Fermi-Level

The distribution of the electron and hole quasi-Fermi levels determines the direction and the magnitude of the total current density. The quasi-Fermi-level distribution can be solved together with the potential distribution from the Poisson equation and the current-continuity equation. If the Poisson equation stands alone, as it does in TWIST, only one unknown, the

potential, can be solved. But quasi-Fermi levels are required for the calculation of carrier densities as shown in Equations (4.7) and (4.8). Thus we need an algorithm to assign the quasi-Fermi levels at each mesh point.

The assignment of quasi-Fermi levels must satisfy the following criteria:

- (a) the quasi-Fermi level should be constant along the direction without current flow,
- (b) the quasi-Fermi levels of both electrons and holes are the same in the neutral regions,

To facilitate the explanation of the quasi-Fermi-level assignment, the definitions of source, drain and channel regions are clarified first. The source, drain, and channel regions differ from those defined by the user because of the two-dimensional impurity redistribution. In the case of an enhancement MOSFET, the region between the surface P-N junction and the neighboring boundary plane is defined as a source/drain region. In the case of a depletion MOSFET, the "surface junction" is defined as the turning point of surface impurity distribution, i.e. the point at which the second-order gradient of impurity distribution along the surface changes the sign. The region between the junctions is the channel region.

In the source and drain regions, only the y-direction correlation of the quasi-Fermi-level distribution is considered. The quasi-Fermi-level assignment is based upon the one-dimensional theory of a P-N junction in y-direction. In the neutral substrate, where the net charge density is less than two thirds of the impurity density, both the electron and hole quasi-Fermi levels are assigned to the substrate bias, zero. In the neutral source and drain, the quasi-Fermi levels are assigned to the bias voltages on the junctions, i.e. V_{SB} and V_{DB} respectively. In the depletion region, where the net charge density is greater than two thirds of the impurity density, E_{fp} , the

hole quasi-Fermi level, of an N-channel MOSFET is assigned to the substrate potential, and E_{F_N} , the electron quasi-Fermi level, is assigned to V_{SB} or V_{DB} .

In an N-channel enhancement MOSFET, E_{F_p} in the channel region is always assigned to the substrate potential, because the hole current is negligible. In the neutral region next to the substrate boundary, E_{F_N} also stays at the substrate potential level. The quasi-Fermi levels will separate only if the surface depletion region exists. In the surface depletion region, two different cases must be considered. In the initialization, E_{F_N} always assumes the bias on the source junction. During the two-dimensional iterations, the horizontal correlation must be included. In a horizontal cross section, E_{F_N} is assigned regionally constant and located at either the source or drain bias, as shown in the band diagram in Figure 4.5. E_{F_N} is at the source level until, at any given depth y , the partial derivative of the electron energy in the x direction becomes negative: in other words, the partial derivative of the potential, ϕ , becomes positive. The boundary of the drain-controlled depletion region is assigned at the place where the potential assumes a further drop of $\frac{kT}{q}$ from the barrier potential. Beyond this point, E_{F_N} is assigned to the drain level. This transition will cause the electron density to drop abruptly at the location where the drain control sets in. Actually, the concentration of the electrons which are injected from the source would drop linearly, in the absence of recombination mechanism, to the boundary of drain-control.

In the channel region of a depletion MOSFET, the junction between the surface and the substrate causes the quasi-Fermi levels to separate. A neutral region may exist between the surface and the junction, and the quasi-Fermi levels also join here.

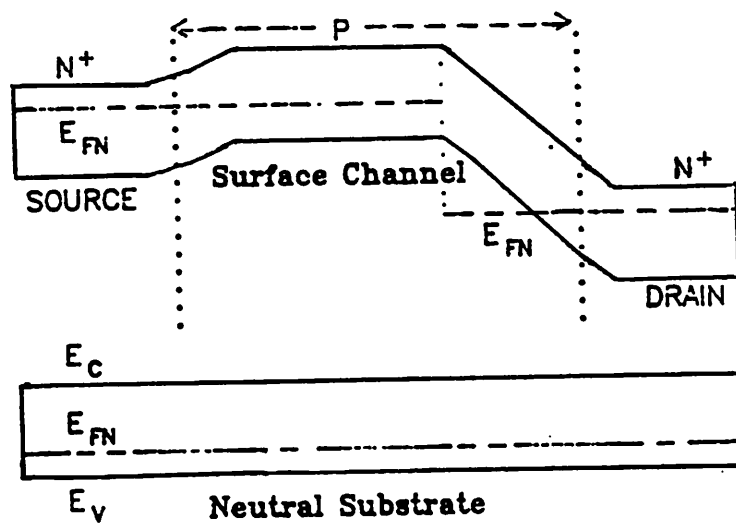


Figure 4.5 The Energy-Band Diagram of an Enhancement N-Channel MOS-FET,

4.5. Potential Initialization

Initialization is necessary and critical for the two-dimensional numerical solution of the Poisson equation. The estimated initial values determine the convergence speed to a large degree. The algorithms which converge fast require closely-estimated and smoothly-distributed initial values.

The potential distribution in a small-geometry MOSFET is inherently two-dimensional, especially in the drain-controlled depletion region which occupies a major portion of the device. The problem is further complicated by the extreme inhomogeneity of impurity distributions. Few of the existing theories can model the potential distribution in this region adequately by analytical expression. Instead of strictly abiding by the theoretical predictions of surface potential distribution, TWIST uses an empirical approach to provide quickly-evaluated, smoothly-distributed initial values. The resultant convergent speed demonstrates its validity.

In the initialization for the low V_{DS} case, the device is partitioned into five vertical domains as shown in Figure 4.6: channel, source and drain, and source- and drain-controlled depletion domains. In the channel, source and drain domains, the potential distributions can be described by the one-dimensional Poisson equation, while in the source- and drain-controlled depletion domains, the potential is a two-dimensional function of both x and y coordinates. The widths of the source- and drain-controlled depletion domains are estimated using the equations described in References [47-48].

In the channel, source and drain domains, one-dimensional self-consistent potential distributions are solved at the left and right boundary planes and the middle cross section of the channel region. These one-dimensional solutions are then assigned to the entire regions to which they belong.

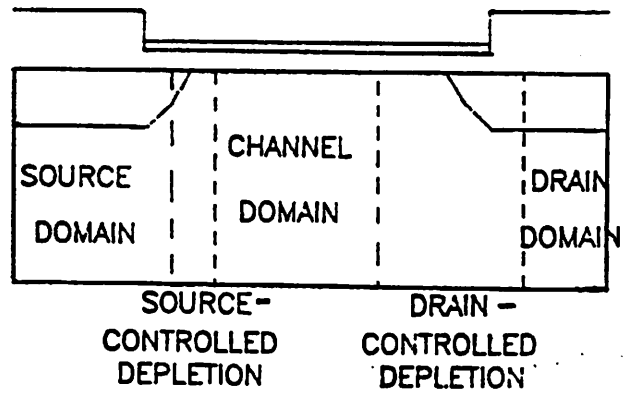


Figure 4.6 The Cross Section of a MOSFET, Divided into Five Domains for Potential Initialization in Cases of Low V_{DS} ,

By using these potential solutions as boundary conditions, the potentials in the source- and drain-controlled depletion domains are assigned using the equation:

$$\phi(x,y) = \phi_1(y) + [\phi_2(y) - \phi_1(y)] \times \left[1 - \sqrt{\frac{\phi_{s2} - \phi_{s1}}{\phi_2(y) - \phi_1(y)} \left[\frac{x - x_1}{x_2 - x_1} \right]} \right]^2 \quad (4.14)$$

for $\phi(x,y)$ lying between $\phi_1(y)$ and $\phi_2(y)$, and x between x_1 and x_2 , where ϕ_{s1} and ϕ_{s2} are the surface potentials at the two boundary planes respectively, and $\phi_1(y)$ and $\phi_2(y)$ are the potentials in the two boundary planes. Whenever the expression gives a value greater than $\phi_2(y)$, $\phi(x,y)$ is limited to $\phi_2(y)$.

The one-dimensional self-consistent potential distributions in the channel, source and drain domains are solved using the following initial conditions:

- (a) In the source and drain domains, the initial potential is based on the one-dimensional P-N junction theory with a uniform substrate. The depletion region is totally allocated inside the substrate.
- (b) In the channel domain, the surface potential of either enhancement or depletion channel is estimated using approximate closed-form solutions of the Poisson equation in the condition of either strong or weak inversion. The depth of the surface depletion region is estimated and the potential is assigned accordingly.

In devices with very short channel lengths and moderate drain biases, the channel domain does not even exist. The drain- and source-controlled depletion domains merge together, as shown in Figure 4.7. The following scheme is designed to initialize this extreme situation:

- (a) Determine the width of the source- and drain-controlled depletion domains based upon analytical expressions [47-48].

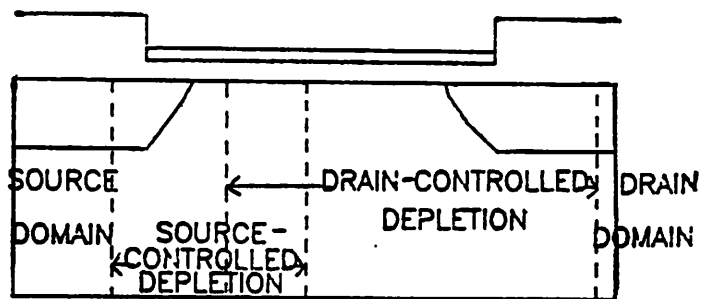


Figure 4.7 The Cross Section of a MOSFET, Divided into Three Domains for Potential Initialization in Cases of High V_{DS} ,

- (b) Limit the drain-controlled depletion domain between the source and drain junctions.
- (c) Assign the potential in the drain-controlled depletion domain using Equation (4.14).
- (d) Use the middle of the overlapping region as the boundary of the source-controlled depletion domain.
- (e) Use the already assigned potentials at the boundaries as the boundary conditions and assign the potentials in the source-controlled depletion domain accordingly.

After the potential distribution of the entire device are initialized, the user may be allowed to modify it. But the auto-initialization results are adequate in most cases tried to date. Figure 4.8 shows the initial and final negative-potentials, which are directly proportional to the electron energies, of a $0.8 \mu m$ device with a channel implant and biases at $V_{GB} = 0.1V$, $V_{DB} = 5V$, $V_{SB} = 0V$.

4.6. Iteration Algorithm and Program Performance

The self-consistent two-dimensional potential distribution is then solved using an iterative method. The resultant potential, field and free carrier distributions can be displayed. The surface- and punchthrough-barrier potentials, the injection locations and the surface depletion regions are determined and displayed.

The Poisson equation in a five-point finite-difference format is solved by the Successive-Over-Relaxation algorithm with a modified alternating-

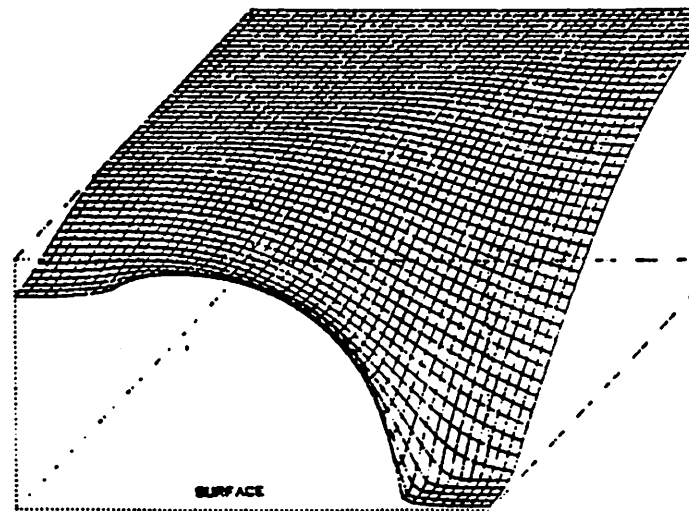
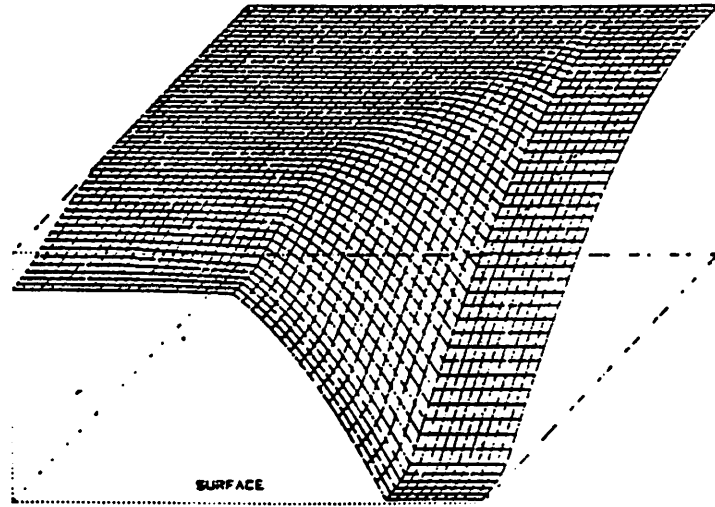


Figure 4.8 The Initialized and Resulting Negative Potential Distributions,

direction method. The mesh is scanned column by column along the horizontal direction. But the scanning direction is reversed every other iteration loop to ensure that the most recent iteration results are used to update the potential at the currently scanned point. The Gummel algorithm is modified to use the potentials of the four immediate neighbors as boundary conditions and to carry out the Newton-Raphson iteration of the potential at each point. Because the correlation is quite localized, the points which converge quickly are detected and skipped in later iteration loops to increase speed. Typically, by the third iteration, about half of the total mesh points of a uniform-mesh setup and one third of the total mesh points of a graded mesh setup are by-passed. More than two thirds of the mesh points are by-passed in later iteration loops. The computational time per iteration loop varies due to the by-pass scheme. The average computational time per two-dimensional iteration loop averages 1-2 seconds for a 50 by 50 mesh setup with $2mV$ resolution.

4.7. Device Characteristics

In the weak-inversion and/or the weak-injection region, the drain current is mainly a diffusion current injected from the source over the regional potential barrier and collected by the drain. So the current is formulated as:

$$I_{DS} = qD \frac{N_I^2 W}{N_{SUB} W_B} \int_0^{W_B} e^{\frac{q(\phi_B(y) - \phi_{SRC})}{kT}} dy \quad (4.15)$$

where W_B is the "base width", ϕ_B is the local barrier potential and ϕ_{SRC} is the source potential. Given a self-consistent potential distribution, the drain diffusion current can be calculated from the barrier potentials at the interface, in the buried channel, and/or at the saddle point at the punchthrough

ridge, and the "base width". In small structures, the barrier may be just a point in the potential profile. In these cases, the "base width" and the depth of the base cross section are calculated as the dimensions of the regions in which the potentials differ from the barrier potential by less than one or two $\frac{kT}{q}$. Although this leaves the base width ambiguous to some extent, the most dominant factor in the current equation is the exponential term depending on the barrier potentials. The larger part of design optimization rests on the control of the various local barrier potential.

CHAPTER 5

The Punchthrough

With recent technological developments in both the accuracy of process control and the fine structure of lithography patterns, the scaled-down MOSFETs promise a higher integration density and a faster switching speed. The scaling approach [49], which requires the reduction of both physical and electrical dimensions in proportion, has practical and physical limitations due to technical constraints and the non-linear relationship between geometrical and physical parameters. One of the most important problems in designing small-geometry MOSFETs is the punchthrough between the source and the drain. It is the result of the barrier lowering due to the merging of the source and drain depletion regions.

Once the punchthrough condition is reached, the current flowing from the source to the drain increases significantly as V_{DS} increases. This additional current can be viewed as an undesirable component to be avoided, or exploited as part of the conduction current in novel applications of MOSFETs [50]. Both approaches require a thorough understanding of punchthrough.

In this chapter, the punchthrough phenomenon is demonstrated by two-dimensional device simulation and theoretical analysis. Section 5.1 describes the close correlation between the punchthrough of the source and the drain and the static-feedback from the drain to the gate. Section 5.2 describes the nature of punchthrough and the locus of the injection point by the results of two-dimensional simulations using Program TWIST. Section 5.3 presents a theoretical analysis of punchthrough, based upon the assumption of uniform substrate doping.

5.1. Static Feedback and Punchthrough

Static-feedback and punchthrough effects are usually cited as two different characteristics associated with short-channel MOSFETs. As a matter of fact, the fundamental mechanisms of these two effects are very similar. Both phenomena can be described as a modulation of the potential barrier between the source and the drain by the drain voltage, V_{DS} , when the channel length is sufficiently short. The static feedback from the drain to the gate is observed as a shift in the threshold voltage due to V_{DS} , and punchthrough is observed as an abnormal current which strongly depends on V_{DS} at a medium or high V_{DS} .

Figure 5.1 shows the surface potential distribution versus the normalized channel length, as simulated by TWIST, in devices of channel lengths ranging from $20\mu m$ to $1.5\mu m$, with a uniform substrate concentration of $2.0 \times 10^{15} cm^{-3}$, biased at $V_{GS} - V_{FB} = 0.6V$, $V_{DS} = 0.0V$ and $V_{BS} = 0.0V$. Under such bias condition, these devices operate in the weak-inversion mode. In a long-channel device, the barrier is wide and flat and its height can be predicted by the one-dimensional Poisson equation in the direction normal to the channel. The barrier width is reduced as the channel length is shortened. In a device of intermediate channel length, the barrier height is the same as that of a long-channel device; however, the source and drain depletion regions fill most of the channel region. A shift in the threshold voltage is observed and can be explained by the overall charge conservation, as modeled by Yau and Lee respectively [51-52]. With a shorter channel length, the source and drain depletion regions merge. The barrier width is reduced to a single point and the height is lowered. In this operational mode, the surface conduction current in weak-inversion, which is independent of the drain voltage in a long-channel device, increases as V_{DS} increases. This phenomenon is called the static-feedback effect; the gate and

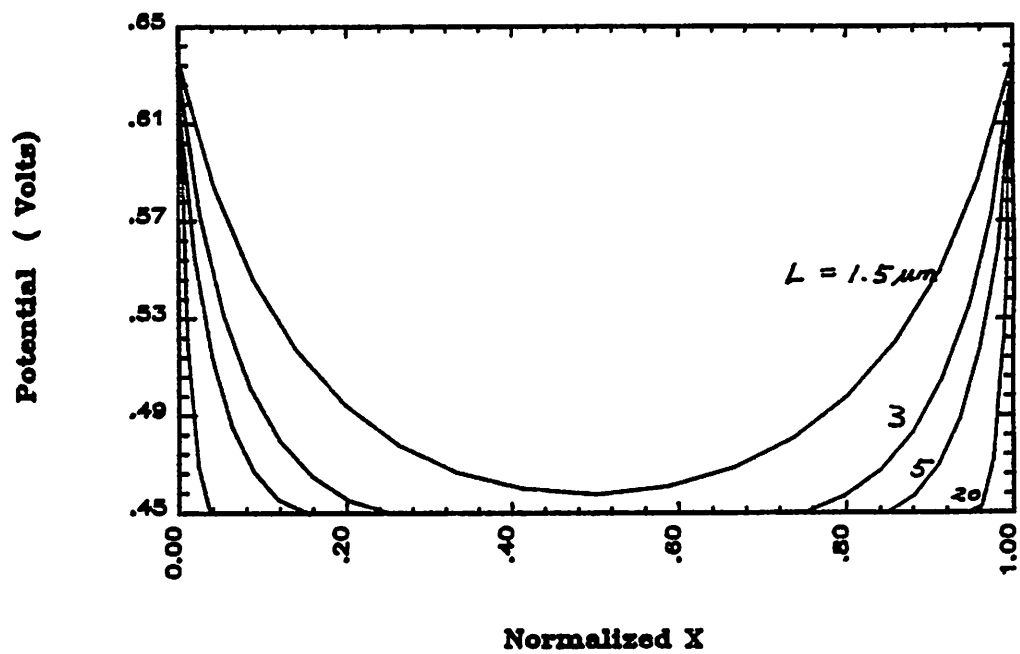


Figure 5.1 The Surface-Potential Distributions versus Normalized Channel Length with Parameter L ,

the drain are coupled together. Both the gate and the drain have a direct control over the barrier. Figure 5.2 shows the surface potential distribution versus the normalized channel length in a device $1.5\mu\text{m}$ long, biased at the same V_{GS} and V_{BS} as in Figure 5.1 and at $V_{DS} = 0.0V, 2.0V$ and $4.0V$. The potential barrier seen from the source is lowered as V_{DS} increases.

The merging of the source and drain depletion regions leads to the lowering of the barrier between them. Under certain bias conditions, the barrier is deep inside the substrate and provides an alternate current path to the surface channel. Because of this extra substrate component, the drain current in the punchthrough mode is more dependent on V_{DS} than the drain current in the weak-inversion mode. Because the gate is shielded from the barrier by the depletion charge, the gate-control over the buried barrier is weaker than that in the weak-inversion mode. The carriers are injected from the source over the buried barrier and flow along the edge of the barrier minimum in the vertical cross sections. The injection barrier is located at the saddle point where the potential is the minimum in the horizontal direction and the maximum in the vertical direction.

The barrier height is lowered as V_{GS} and/or V_{DS} increase and raised as V_{SB} increases. The buried injection barrier moves toward the surface as V_{GS} and/or V_{SB} increase, and away from the surface as V_{DS} increases. The operational mode shifts gradually from punchthrough to static feedback as the injection point moves toward the surface and vice versa. In the low current region, both operational modes are barrier-controlled. The shift between static feedback and punchthrough is demonstrated by a series of two-dimensional simulations of a device with $L = 1\mu\text{m}$, $T_{OX} = 0.065\mu\text{m}$, $x_j = 0.5\mu\text{m}$, and $N_{SUB} = 0.75 \times 10^{15} \text{cm}^{-3}$. Figures 5.3, 5.4, and 5.5 show the equal-potential contours. The injection point is the point at which the equal-potential lines meet or form closed circles. Figure 5.3 shows the

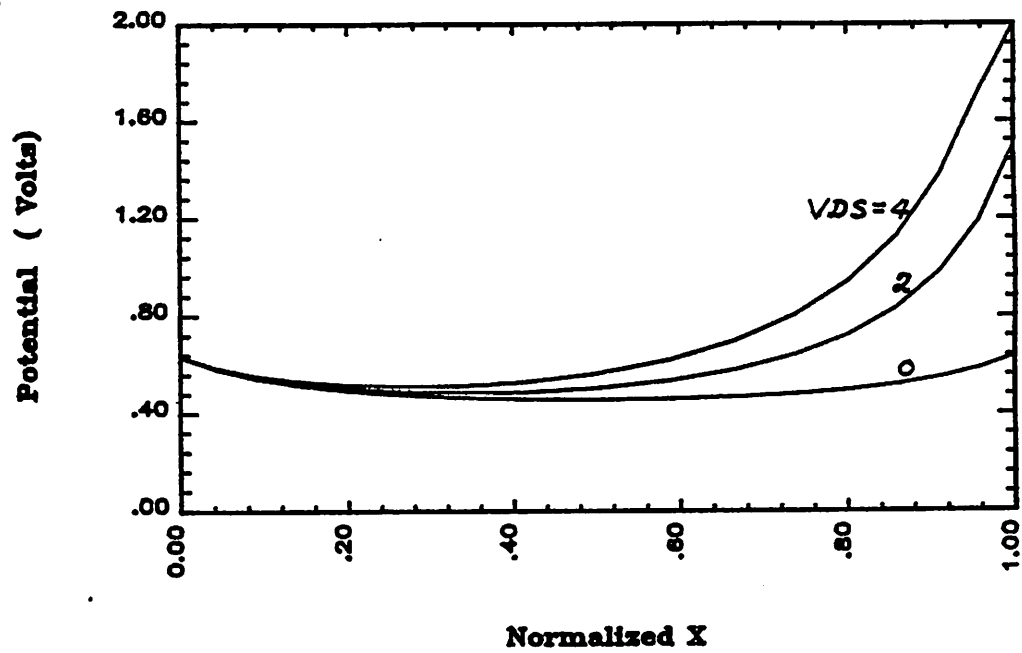


Figure 5.2 The Surface-Potential Distributions versus Normalized Channel Length with Parameter V_{DS} .

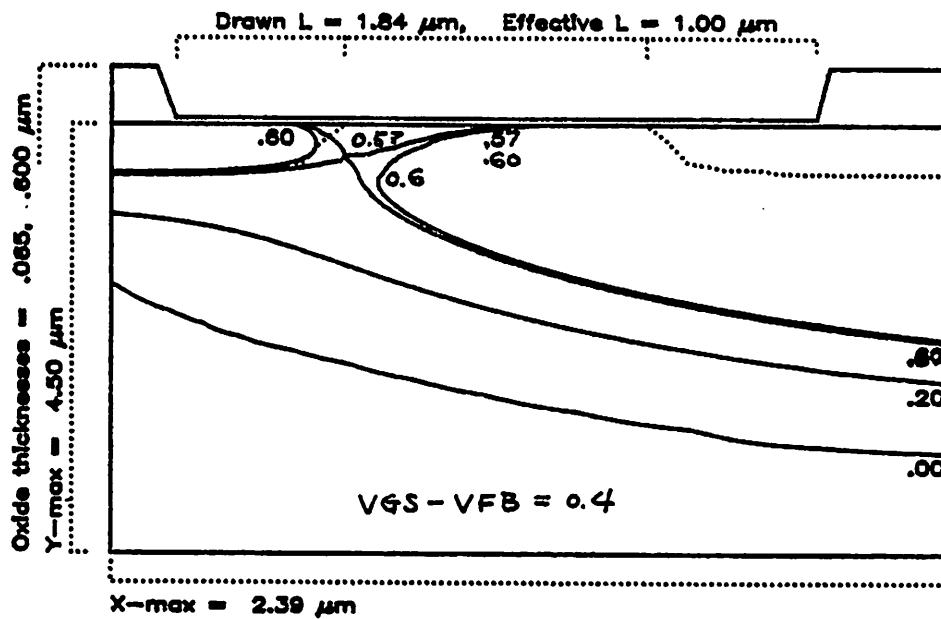
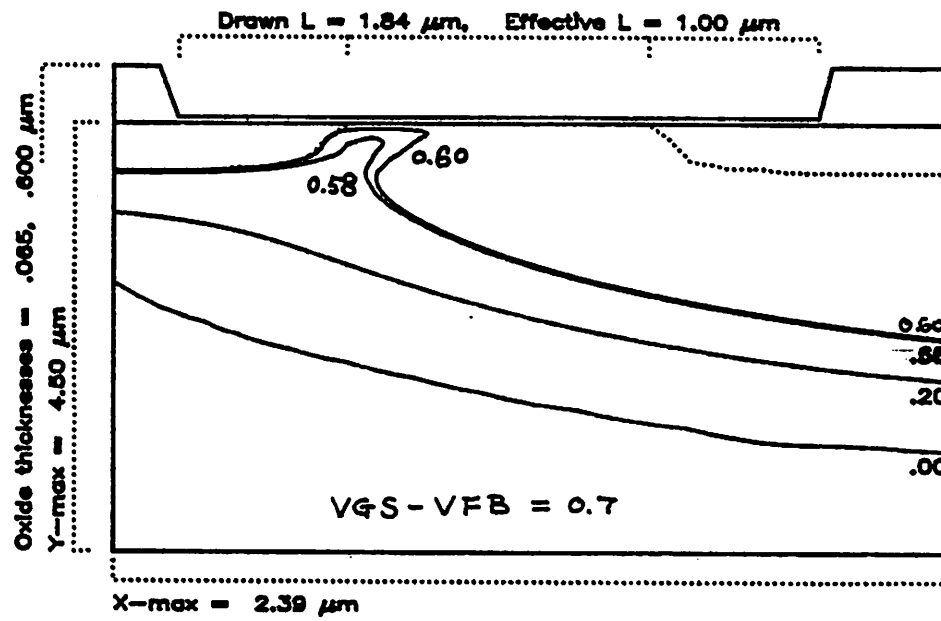


Figure 5.3 The Equal-Potential Contours at $V_{DS} = 4V$ and $V_{BS} = 0V$ with $V_{GS} - V_{FB} = 0.7V$ and $0.4V$,

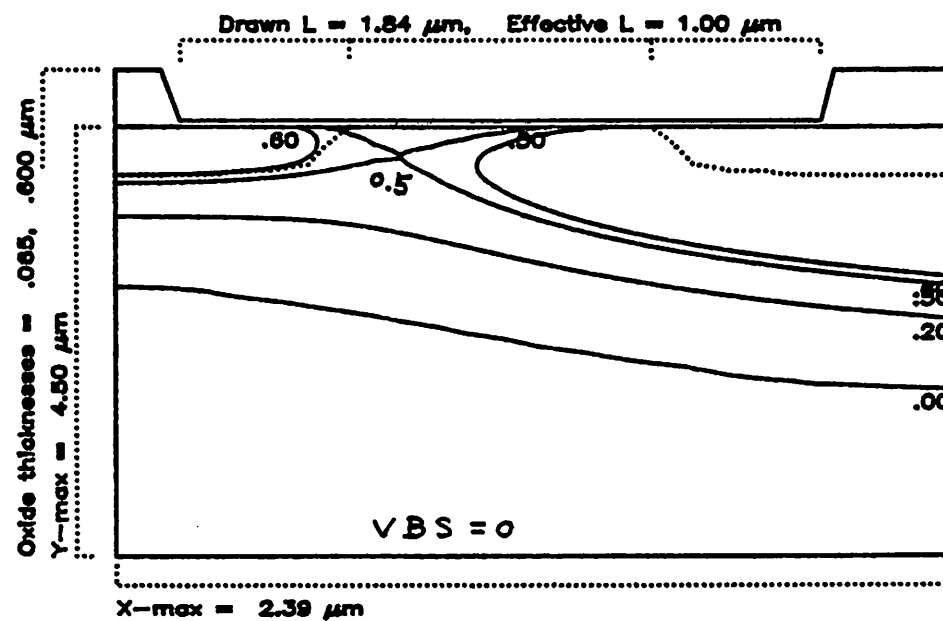
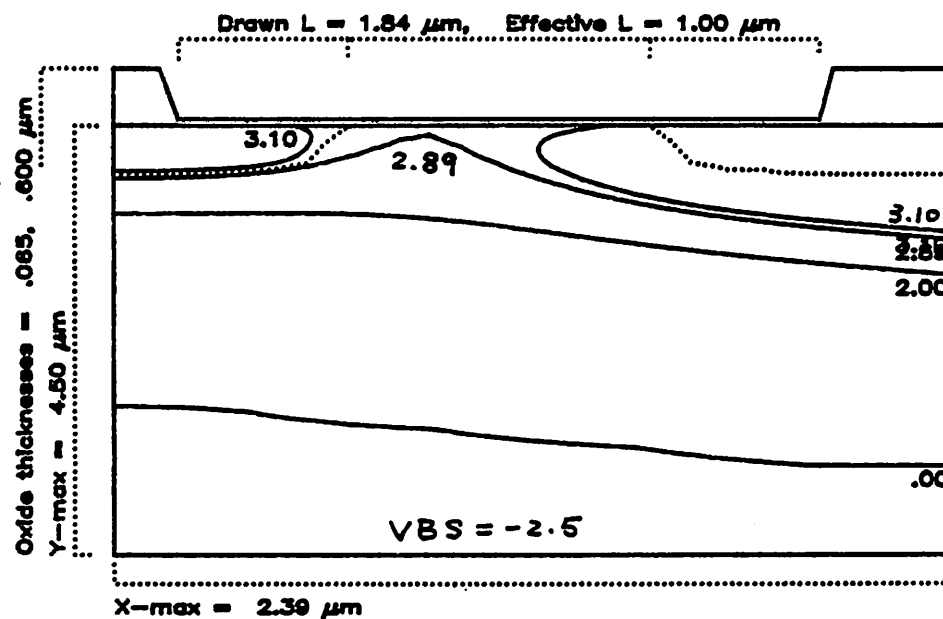


Figure 5.4 The Equal-Potential Contours at $V_{DS} = 2V$ and $V_{GS} - V_{FB} = 0.4V$ with $V_{BS} = -2.5V$ and $0V$,

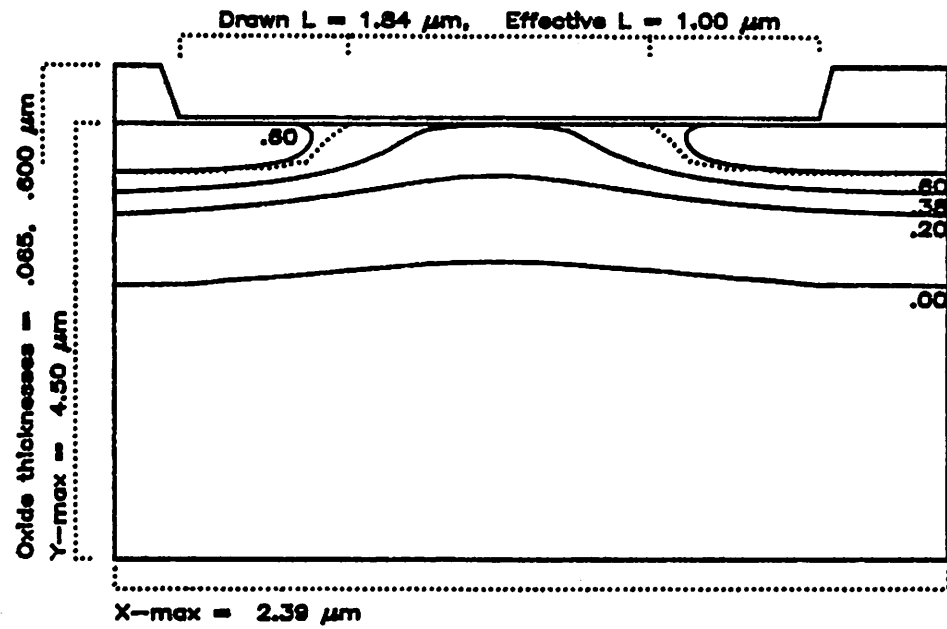


Figure 5.5 The Equal-Potential Contours at $V_{DS} = 0.0V$, $V_{GS} - V_{FB} = 0.4V$ and $V_{BS} = 0V$,

equal-potential contours at $V_{DS} = 4V$ and $V_{BS} = 0V$ with $V_{GS} - V_{FB}$ at 0.7 V and 0.4 V. The injection point moves from $(x,y)=(0.554 \mu m, 0.0 \mu m)$ to $(x,y)=(0.484 \mu m, 0.386 \mu m)$ and the barrier potential moves from 0.630 V to 0.567 V as V_{GS} moves from 0.7 V to 0.4 V. Figure 5.4 shows the contour plots at $V_{DS} = 2V$ and $V_{GS} - V_{FB} = 0.4V$ with V_{BS} at -2.5 V and 0.0 V. The injection point moves away from the surface as V_{BS} decreases and the height of the injection barrier is lowered. Figure 5.5 shows the contour plot of the same device at $V_{DS} = 0.0V$, $V_{BS} = 0.0V$ and $V_{GS} - V_{FB} = 0.4$. By comparing it with Figure 5.4, one sees that the injection point moves toward the surface and the barrier height increases as V_{DS} decreases.

5.2. The Saddle Point

When a long-channel MOSFET is biased at $V_{DS} = 0.0V$, $V_{BS} = 0.0V$ and $V_{GS} = V_{FB}$, the channel region assumes a constant potential from the surface through the substrate. In a short-channel MOSFET with the same process parameters at the same bias, the flatband configuration is modified by the merged depletion regions. Inside the overlapped depletion region, charges are shared between the source and drain junctions. The more the charges are shared, the lower the potential barrier is sustained. The barrier height is lowered and the potential distribution at the channel center is no longer flat. Since more charges are shared at the surface than inside, the deviation from the flatband condition is largest at the surface. However, the gate voltage tends to hold the potential at the flatband. The gate influence decreases as it penetrates the substrate. The combined effects of the gate voltage and the merging of the depletion regions result in a potential maximum in the vertical cross sections as shown in Figure 5.6(a). The horizontal minimum of the potential distribution in each cross section is located at the center of the device because V_{DS} is zero. Thus the resulting potential distribution looks like a

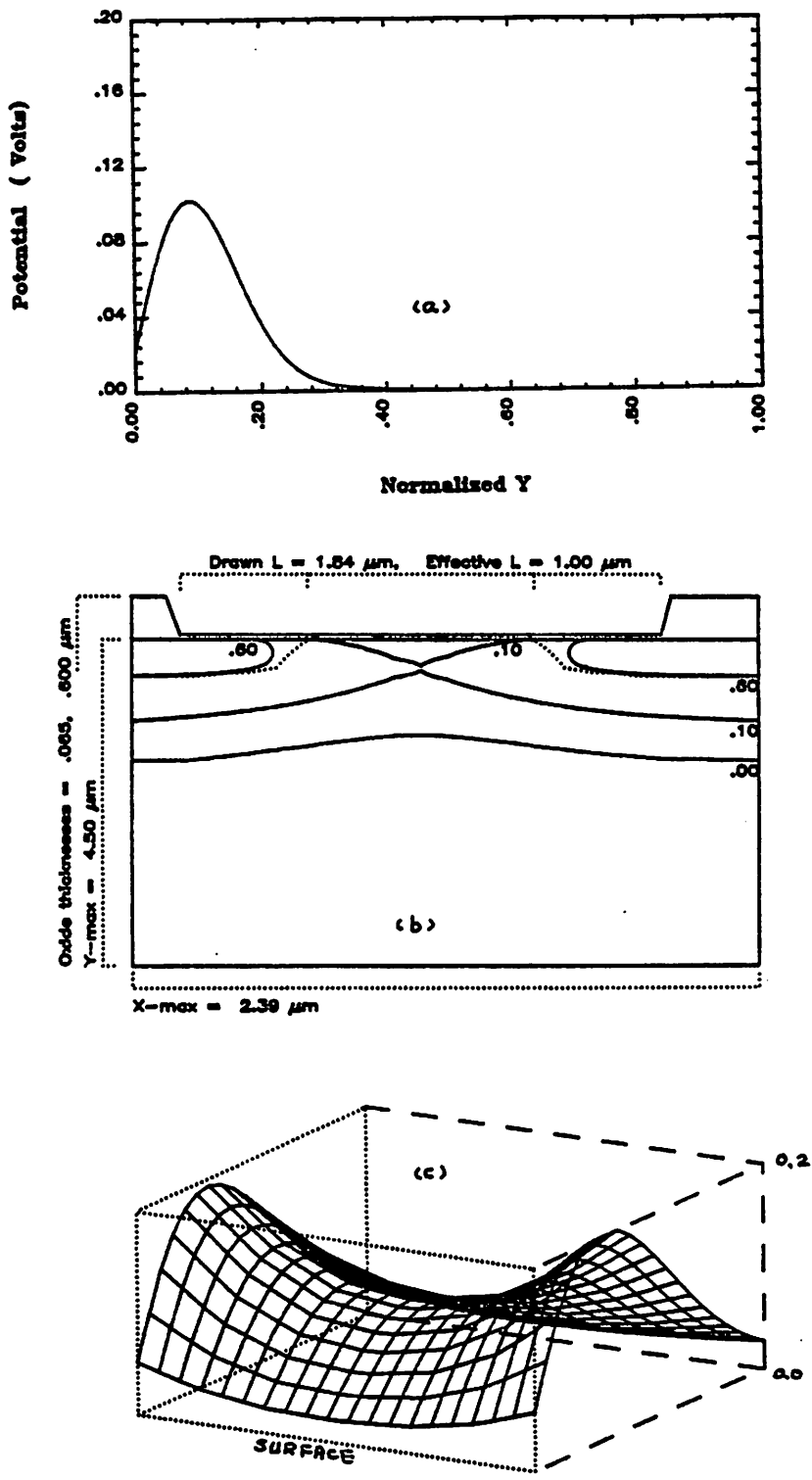


Figure 5.6 Potential Distributions at $V_{DS} = 0V$, $V_{GS} = 0V$ and $V_{GS} - V_{FB} = 0V$,
 (a) Potential Distribution in the Normal Cross Section of the
 Channel Center, (b) Equal-Potential Contours, (c) Three-
 Dimensional Potential Distribution,

saddle. The equal-potential contours and the three-dimensional potential distribution are shown in Figures 5.6(b) and (c) respectively.

The saddle point's location and its potential can be modulated by the bias of the device as shown in Figures 5.3, 5.4, and 5.5. The locus of the saddle points and the barrier potential and height are listed in Table 5.1 as a function of biases:

Table 5.1						
VDS (V)	VGS (V)	VSB (V)	Saddle (V)	Height (V)	XB um	YB um
1.0	.40	0.0	.422	.460	.718	.192
2.0	.40	0.0	.501	.381	.632	.297
3.0	.40	0.0	.548	.334	.554	.336
4.0	.40	0.0	.587	.315	.484	.336

Table 5.1 Properties of the Saddle Point as a Function of Biases

5.3. Quasi-One-Dimensional Analysis

As illustrated in the previous section, in either the static-feedback or punchthrough mode, the influences of V_{GS} , V_{BS} and V_{DS} are coupled together. The potential distribution is inherently two-dimensional. The author handles the analysis by decoupling the two-dimensional Poisson equation into a simpler one-dimensional format and introducing quasi-empirical parameters to model two-dimensional effects on the onset voltage of punchthrough.

One- and two-dimensional charged systems differ in charge sharing. In a two-dimensional system, the charge supports the potential differences in both the x and y directions while in a one-dimensional system, the charge

supports the potential difference in only one direction. In MOSFETs in the barrier-controlled mode, the potential barrier in either direction is supported by only part of the depletion charge between the source and the drain. This can be modeled by replacing the doping concentration in the pseudo depletion region by a higher pseudo concentration. The pseudo depletion region can be penetrated only by applying a higher bias across the source and drain junctions than predicted by one-dimensional theories.

In the two-dimensional Poisson equation:

$$\nabla_x^2 \phi + \nabla_y^2 \phi = -\frac{\rho(x,y)}{\epsilon_{st}} \quad (5.1)$$

The left side of Equation (5.1) can be replaced by $\frac{qN_A}{\epsilon_{st}}$ in the case of an N-channel MOSFET. The term of the second-order derivative in the vertical direction, y , contributes to the pseudo density in the pseudo depletion region. In the punchthrough mode, the second-order derivative at the saddle point can be approximated as:

$$\nabla_y^2 \phi = \frac{1}{L_D} \left[\frac{V_B - \phi}{W_1} - \frac{\phi - \phi_s}{W_0} \right] \quad (5.2)$$

$$= -\frac{1}{L_D} \left[\frac{\phi}{W_1} + \frac{\phi - \phi_s}{W_0} \right] \quad (5.3)$$

where W_1 and W_0 are the widths of the depletion regions below and above the saddle point in the vertical cross section. They can be approximated by

$$W_1 = \sqrt{\frac{2\epsilon_{st}\phi}{qN_A}} \text{ and } W_0 = \sqrt{\frac{2\epsilon_{st}(\phi - \phi_s)}{qN_A}} \text{ respectively. } L_D \text{ is the Debye}$$

length, $\sqrt{\frac{2\epsilon_{st}kT/q}{qN_A}}$. After substituting W_1 , W_0 and L_D in the above equation, $\nabla_y^2 \phi$ can be expressed as:

$$\nabla_y^2 \phi = -\frac{qN_A}{2\epsilon_{st}} \left[\sqrt{\frac{\phi}{kT/q}} + \sqrt{\frac{\phi - \phi_s}{kT/q}} \right] \quad (5.4)$$

This is a negative quantity. By moving this term to the right side of Equa-

tion (5.1), the equation can be rewritten as:

$$\nabla_x^2 \phi = \frac{qN_A}{\epsilon_{st}} - \nabla_y^2 \phi \quad (5.5)$$

$$= \frac{qN_A}{\epsilon_{st}} \left[1 + \frac{1}{2} \left[\sqrt{\frac{\phi}{kT/q}} + \sqrt{\frac{\phi - \phi_s}{kT/q}} \right] \right] \quad (5.6)$$

The two-dimensional effect is equivalent to an increase in the effective substrate doping concentration. By defining the scaling factor of the substrate doping concentration, F , as:

$$F = 1 + \frac{1}{2} \left[\sqrt{\frac{\phi}{kT/q}} + \sqrt{\frac{\phi - \phi_s}{kT/q}} \right] \quad (5.7)$$

The Poisson equation then assumes a one-dimensional format:

$$\nabla_x^2 \phi = \frac{qN_A}{\epsilon_{st}} F \quad (5.8)$$

By using an effective doping density, $N_A F$, the one-dimensional concept of punchthrough can be applied.

As illustrated in the one-dimensional band diagram in Figure 5.7, when the source and drain depletion regions merge and the barrier potential is lowered so that it is less than the junction built-in potential, the source is essentially forward biased and the punchthrough current starts to flow. At the onset of punchthrough, the relationship of the depletion widths to each other is formulated, based upon the assumption of complete depletion:

$$W_D + W_S = L \quad (5.9)$$

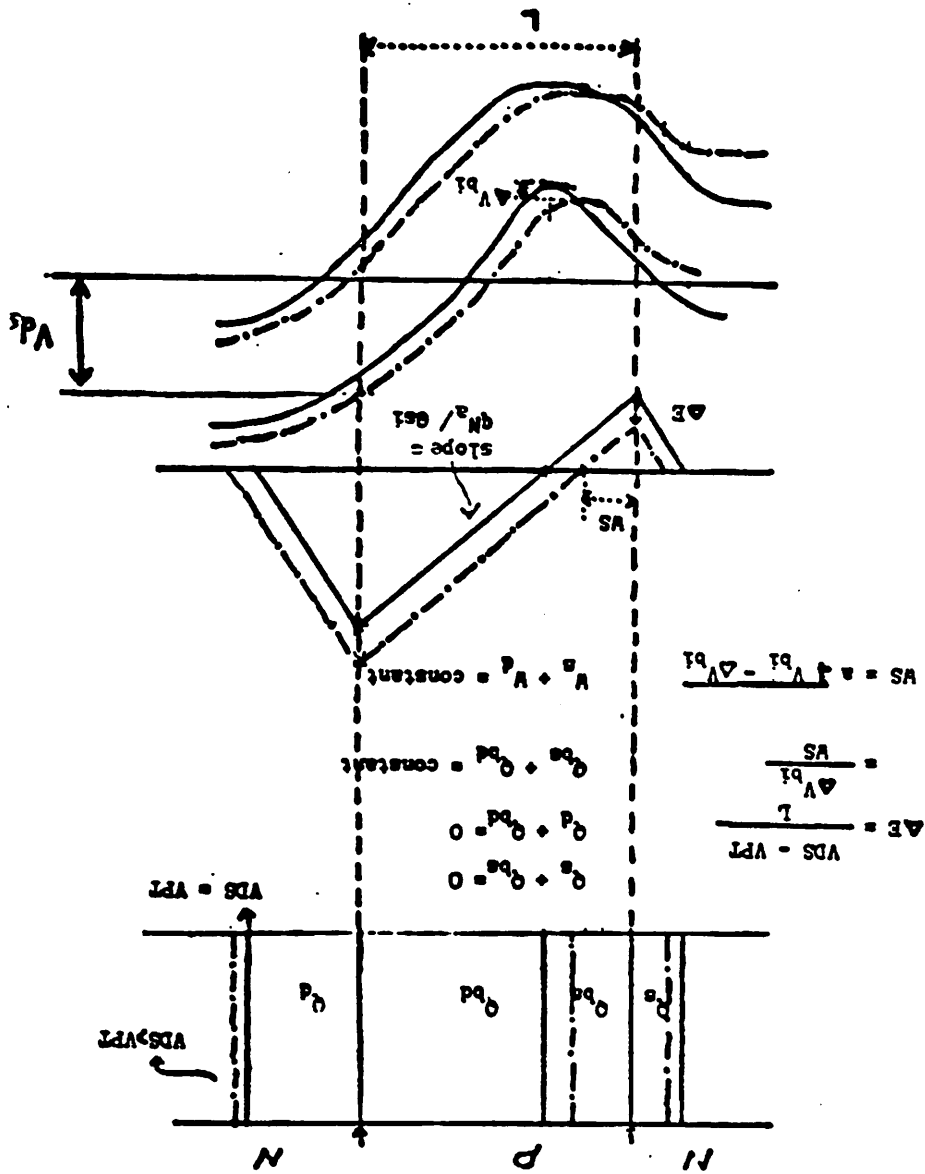
where W_D and W_S are the depletion region widths of the source and drain junctions:

$$W_S = \sqrt{\frac{2\epsilon_{st}\phi_J}{qN_A F}} \quad (5.10)$$

$$W_D = \sqrt{\frac{2\epsilon_{st}[\phi_J + V_{PT}]}{qN_A F}} \quad (5.11)$$

The onset voltage of punchthrough, V_{PT} , can be expressed as:

Figure 5.7 The One-Dimensional Potential Distribution between the Source and Drain Junctions at Punchthrough,



$$V_{PT} = [\alpha L]^2 F - 2\alpha L \sqrt{\phi_J F} \quad (5.12)$$

where

$$\alpha = \sqrt{\frac{2\epsilon_{sd}}{qN_A}} \quad (5.13)$$

By substituting the explicit expression F in Equation (5.13), V_{PT} becomes:

$$V_{PT} = \alpha L^2 \left[1 + \frac{1}{2} \left[\sqrt{\phi_J + V_{SB}} + \sqrt{\phi_J + V_{SB} - \phi_s} \right] \right] - 2\alpha L \sqrt{\phi_J \left[1 + \frac{1}{2} \left[\sqrt{\phi_J + V_{SB}} + \sqrt{\phi_J + V_{SB} - \phi_s} \right] \right]} \quad (5.14)$$

ϕ_J is the barrier height between the source and the drain at the onset of punchthrough. It is a constant, while ϕ_s is the value of the surface potential with the reference potential at V_B . In the barrier-controlled mode, the surface is weakly inverted and the surface potential, ϕ_s , can be approximated as a linear function of V_G :

$$\phi_s = aV_{GB} + b \quad (5.15)$$

$$\phi_s = a[V_{GS} - V_{BS}] + b \quad (5.16)$$

The second square-root term in the expression F depends only on V_{GS} . As illustrated in the previous section, V_{GS} and V_{BS} can affect the barrier potential and its location. In other words, they modulate the pseudo substrate doping density.

A major feature of Equation (5.12) is the dependence of V_{PT} on V_{BS} and V_{GS} . If the two-dimensional effect factor, F , is ignored, that the depletion regions have just merged, the intrinsic onset voltage of punchthrough, V_{PT}^o , is independent of V_{BS} and V_{GS} :

$$V_{PT}^o = [\alpha L]^2 - 2\alpha L \sqrt{\phi_J} \quad (5.17)$$

An empirical formulation of V_{PT} is proposed based upon Equation (5.12):

$$V_{PT} = \alpha + \beta \sqrt{V_{SB} + \phi_J} + \delta \sqrt{V_{GS} - V_{FB}} \quad (5.18)$$

Three empirical factors, α , β and δ are introduced.

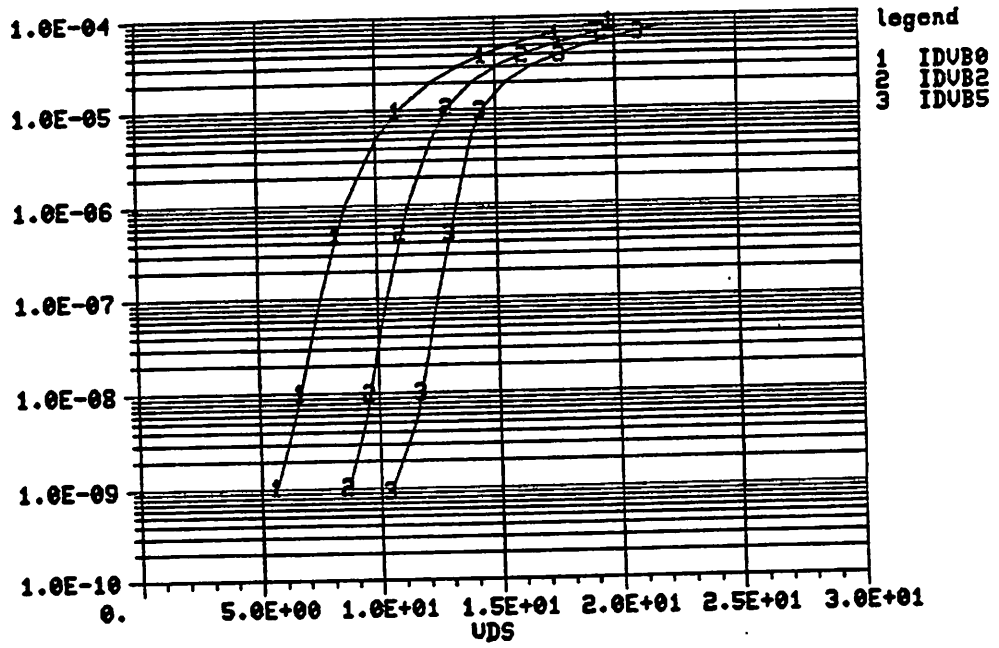
Experimentally, V_{PT} can be defined as the drain voltage at which the normalized drain current, $\frac{L}{W} I_{DS}$, is below $10^{-9} amp$ and V_{GS} is below V_{FB} . A low V_{GS} is chosen to suppress the surface current. Figure 5.8 shows the measured I_{DS} -versus- V_{DS} of device A with parameter V_{GS} and V_{BS} . Figure 5.9 shows the characteristics of device B. V_{PT} -versus- V_{GS} with parameter V_{BS} and V_{PT} -versus- V_{BS} with parameter V_{GS} of device A are plotted in Figure 5.10. The characteristics of device B are plotted in Figure 5.11. The device parameters and punchthrough coefficients which are obtained by linear regression are listed in Table 5.2:

Param	Unit	Dev. A	Dev. B
W	um	50	50
L	um	1.53	1.8
Na	1E15 cm-3	1.78	0.75
Tox	um	0.08	0.065
Xj	um	0.85	0.5
Vto	V	0.05	-0.2
VFB	V	-0.86	-1.01
alpha	V	-0.08	4.79
beta	sqrt V	3.93	4.23
delta	sqrt V	1.94	3.6

Table 5.2 Device Parameters and Punchthrough Coefficients

The limitation in circuit design is determined by the maximal allowable leakage current. The onset of punchthrough conduction can be used as a limiting voltage in circuit-design applications.

DEVICE A AT $V_{GS} = -2$



DEVICE A AT $V_{BS} = 0$

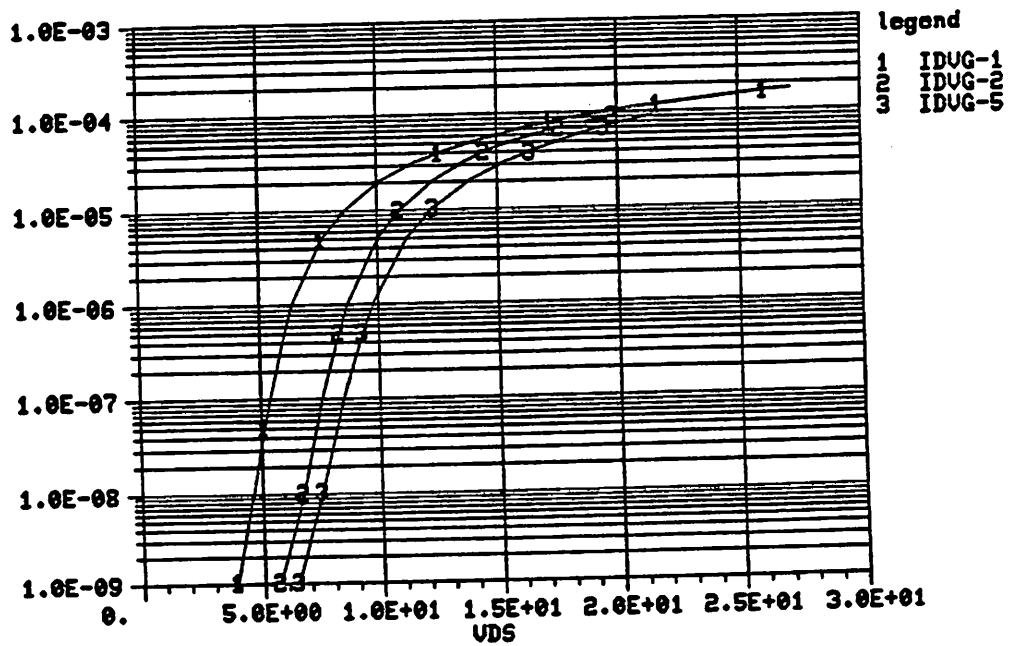
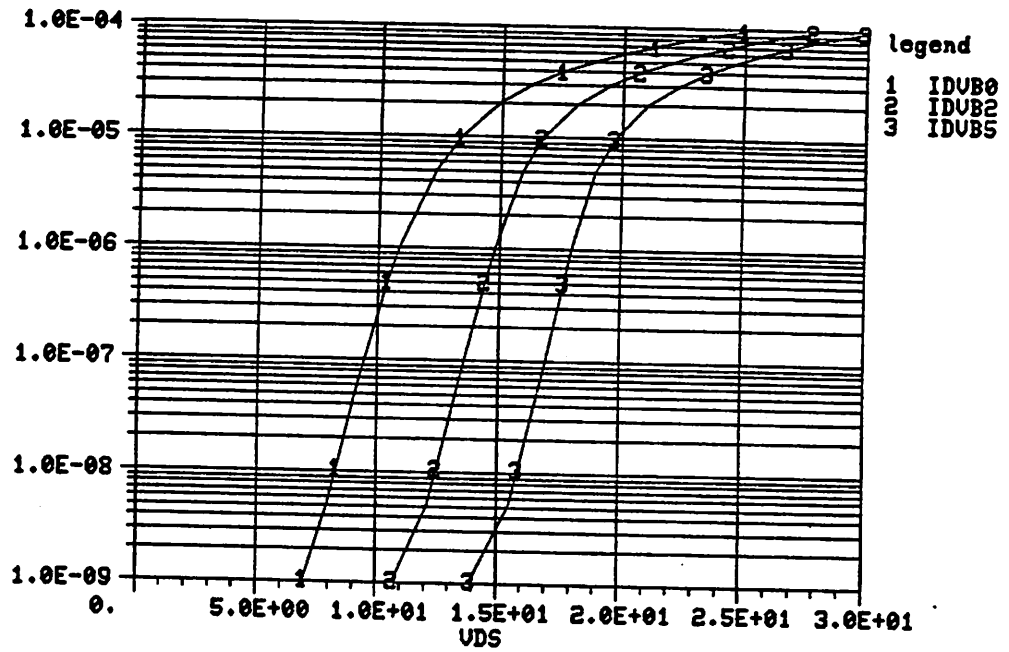


Figure 5.8 The Measured I_{DS} -versus- V_{DS} with Parameters V_{BS} and V_{GS} of Device A,

DEVICE B AT $V_{GS}=-1$



DEVICE B AT $V_{BS}=-2$

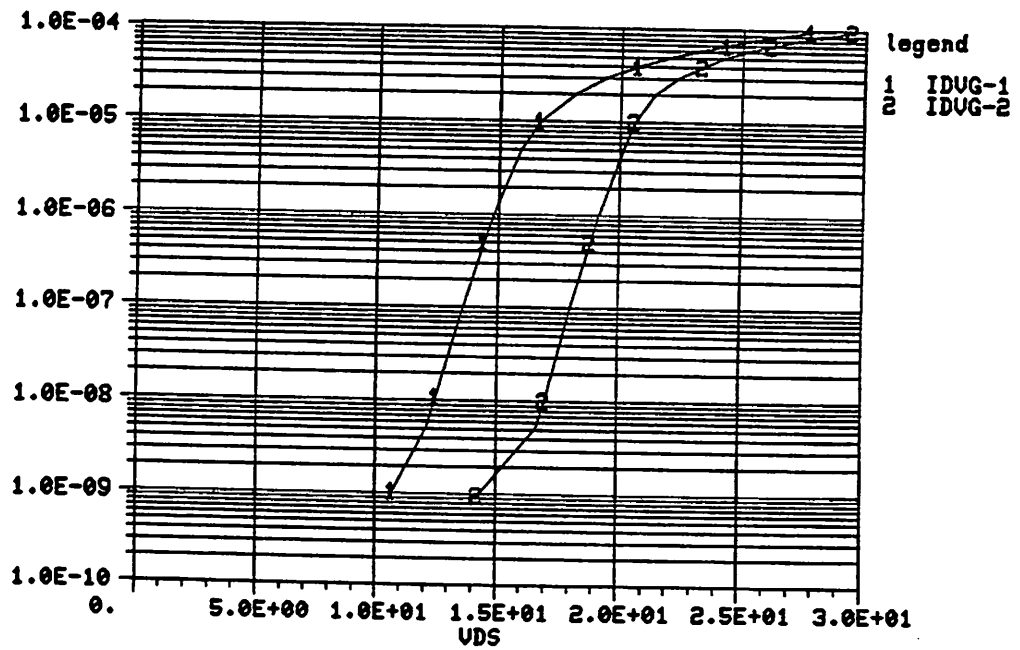
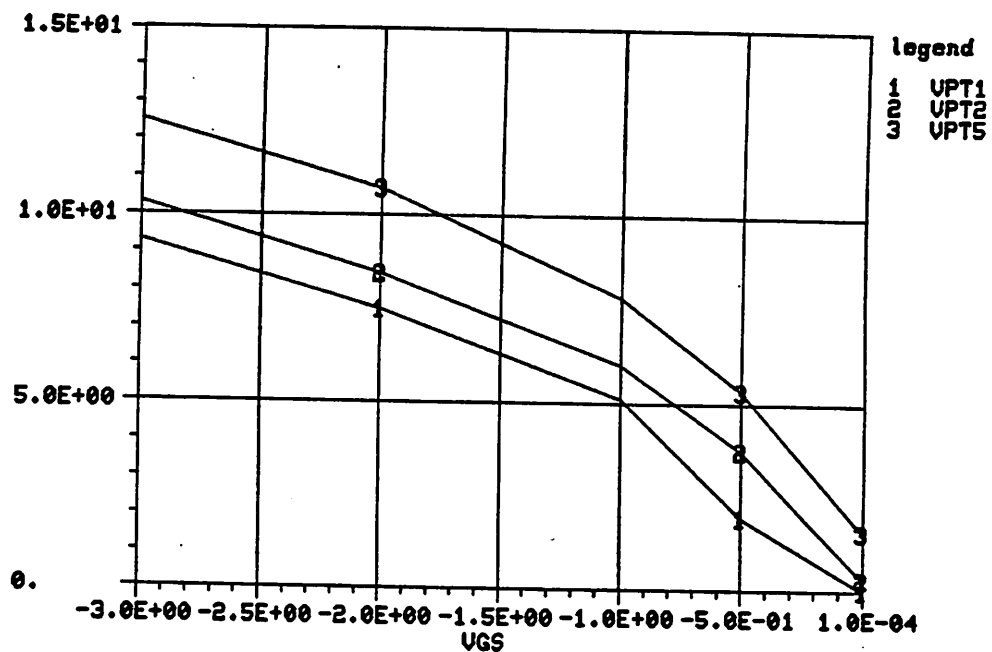


Figure 5.9 The Measured I_{DS} -versus- V_{DS} with Parameters V_{BS} and V_{GS} of Device B,

DEVICE A AT $V_{BS} = -1, -2, -5$



DEVICE A AT $V_{GS} = -1, -2, -3$

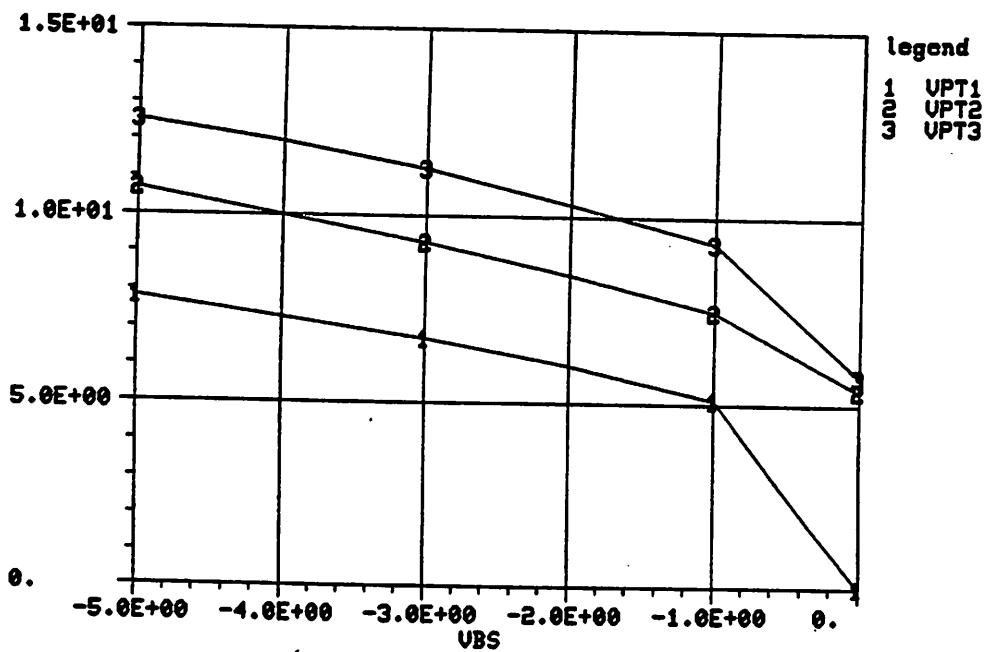


Figure 5.10 V_{PT} -versus- V_{GS} with Parameter V_{BS} and V_{PT} -versus- V_{BS} with Parameter V_{GS} of Device A,

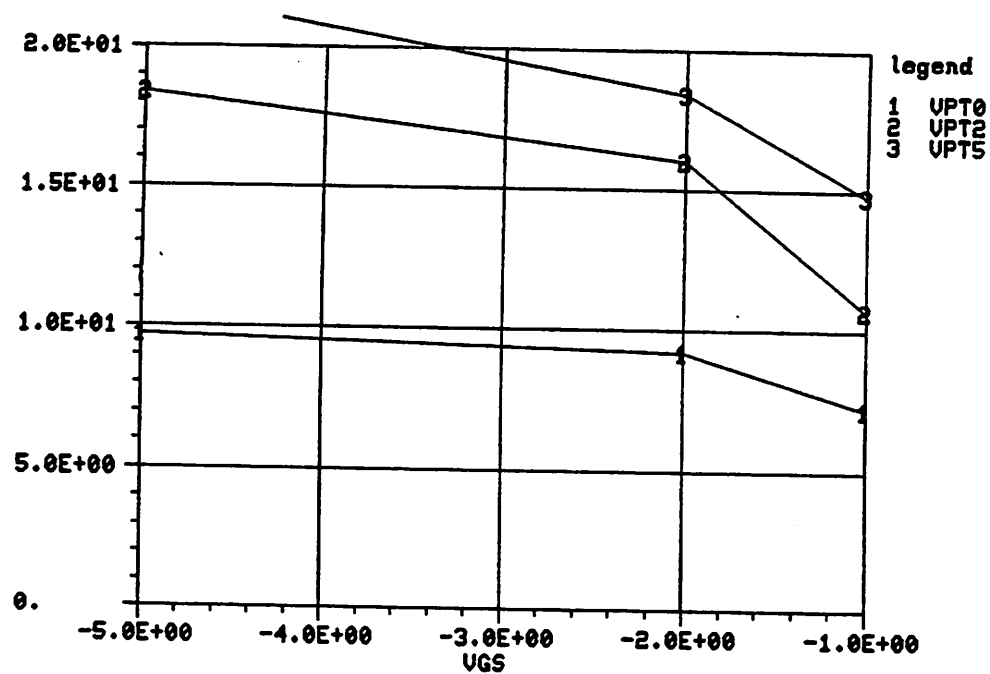
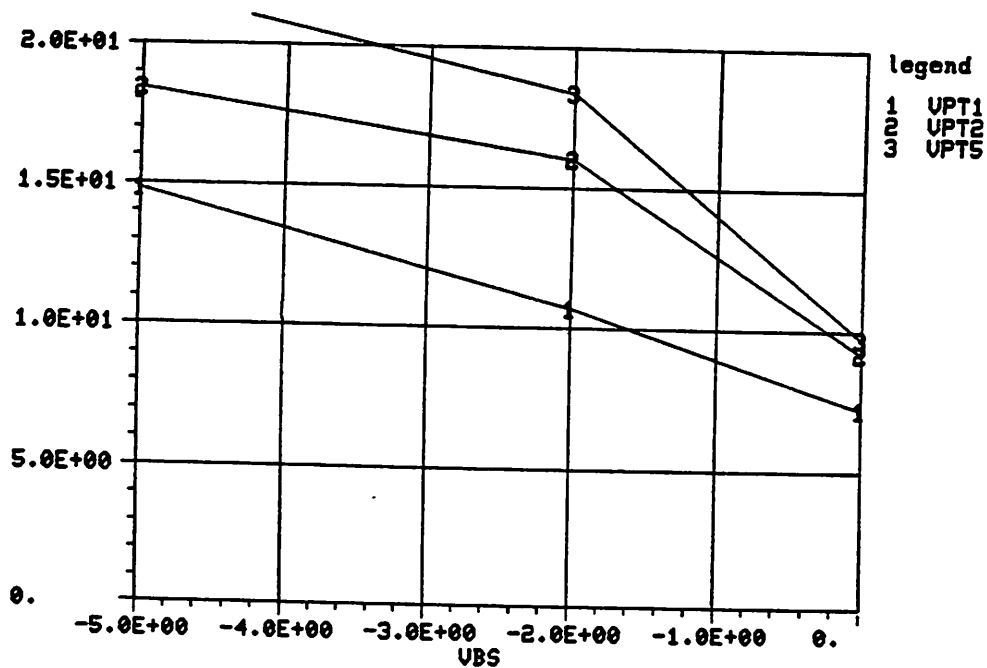
DEVICE B AT $V_{BS}=0, -2, -5$ DEVICE B AT $V_{GS}=-1, -2, -5$ 

Figure 5.11 V_{PT} -versus- V_{GS} with Parameter V_{BS} and V_{PT} -versus- V_{BS} with Parameter V_{GS} of Device B,

CHAPTER 6

Small-Geometry Effects and the Semi-empirical Model MOS3

Besides the punchthrough phenomenon, advances in process technology to achieve small device geometries also bring into prominence other effects which do not appear in the characteristics of the devices of long or even medium channel lengths. In very small MOSFETs, the electrical dimensions, which determine the device characteristics, could not always scale proportionally as the other parameters. For example, the depletion-layer width of a P-N junction is related to the built-in potential of the junction by a square-root expression. The built-in potential depends logarithmically on the substrate doping density. Thus the depletion-layer width does not scale linearly with the doping density. Keeping the operational voltage constant during scaling, instead of strictly following the scaling rules, causes high-field phenomena such as the velocity saturation of hot electrons.

A small-geometry MOSFET with $L \leq 2\mu m$ and $W \leq 2\mu m$ can be characterized by the following features:

- (a) Threshold-voltage sensitivity to the length and the width of the device due to the two-dimensional nature of the potential distribution;
- (b) Threshold-voltage sensitivity to the drain voltage due to the drain-induced lowering of the barrier;
- (c) Relaxed transition between the linear and saturation regions due to the velocity saturation of hot electrons;
- (d) Lowered saturation voltage and current due to the velocity saturation of hot electrons.

This chapter describes the MOS3 model which was developed and implemented in the circuit simulation program SPICE2 (Version 2G.1) to address the above problems and attain computational efficiency. The companion capacitance model, which conserves charge [53], is also derived and implemented.

As demonstrated in the previous chapter, the ultimate difficulty in developing a model for small devices is the correct treatment of the two-dimensional configuration. A complete analytical solution is too complex for the application in circuit simulations in even the simplest ideal case, not to mention the more complicated two-dimensional simulations. A semi-empirical modeling approach is a compromise between simulation accuracy and computational efficiency. In addition, if the model equations can be written in a simple format, they will allow easy parameter extraction, a property which is as critical as the accuracy of the model itself.

The semi-empirical approach to MOSFET modeling proceeds as follows:

- (a) Perform two-dimensional analyses, taking into account the details of the device configuration;
- (b) Derive semi-empirical relationships between parameters based upon the linearization of the two-dimensional simulation results. The resulting model is accurate only within the range of process parameter variations for which two-dimensional results are investigated.

The threshold voltage is the most critical parameter and is investigated in Section 6.1. The threshold-voltage sensitivity of small devices is emphasized. Section 6.2 presents the basic current equation upon which the model is based. In Sections 6.3 to 6.7, second-order effects, including mobility modulation, velocity saturation, channel-length modulation and capacitances, are described in sequence. The last section compares the MOS2 and

MOS3 models. Examples of circuit simulations are included to demonstrate the validity of the semi-empirical model.

6.1. Threshold Voltage

The threshold voltage, V_{TH} , of a long-channel device, say $L > 20\mu m$, depends on the substrate bias. Their relationship can be predicted by applying the charge-conservation principle to a vertical cross section of the device in the middle of the channel. This cross section is bounded by the gate and the substrate. In the channel:

$$Q_g = - [Q_{DEP} + Q_{INV}] \quad (6.1)$$

and $Q_{INV} = 0$ at $V_{GS} = V_{TH}$. Q_g , Q_{DEP} and Q_{INV} are the gate, depletion and inversion charges respectively. The result is:

$$V_{TH,L} = V_{FB} + \phi + \sqrt{2\epsilon_s q N_{SUB}(\phi + V_{SB})} \quad (6.2)$$

where $V_{TH,L}$ is the threshold voltage of long-channel devices, V_{FB} the flatband voltage, ϕ the surface potential at threshold and V_{SB} the source to substrate bias. This expression is not applicable for small devices whose threshold voltages should be determined by the overall charge conservation [48,51-52] of the entire channel.

In the lengthwise cross section of a device, the field lines which originate in the depletion charges near the ends of the channel terminate at the source or the drain, instead of the gate. Thus, the effective threshold voltage is reduced as the channel length is shortened.

On the other hand, the depletion region actually extends beyond the edges of the channel widthwise. The extra charges at the edges sustain field lines which terminate at the gate and result in a higher threshold voltage as

compared to a wide device. The threshold voltage increases as the channel width decreases.

In the case of a long, wide device, the percentage of the charge at the edges is negligible. In a short and/or narrow device, this percentage is significant enough to make the shift in the threshold voltage visible. In MOS3, the effects of the channel length and width and the drain voltage on the threshold voltage are decoupled.

6.1.1. Short-Channel Effects

In a device of intermediate channel length, say $5\mu m$, the surface potential barrier is the same as that of a long-channel device, say $20\mu m$. However, the source and drain depletion regions at the edges occupy most of the channel cross section. The surface potential at the edge is higher than that at the corresponding region of a long-channel device and results in a higher concentration of conduction carriers, as shown in Figure 6.1. The average channel conductance is higher than that of a long-channel device, and the effective threshold voltage is lowered. By assuming a trapezoidal partition [51] of the depletion charge, and applying the cylindrical-junction approximation [48], one can formulate the correction factor of the threshold voltage as:

$$F_S = 1 - \frac{x_J}{L} \left[\left[\frac{W_C}{x_J} + \frac{L_D}{x_J} \right] \sqrt{1 - \left(\frac{W_P/x_J}{1 + W_P/x_J} \right)^2} - \frac{L_D}{x_J} \right] \quad (6.3)$$

which is used to multiply the depletion-charge term, the square root, in Equation (6.2). The threshold-voltage shift due to the short-channel effect with $N_{SUB} = 5.0 \times 10^{15} cm^{-3}$, $T_{OX} = 0.1\mu m$, $x_J = 0.5\mu m$, and a channel length of $2\mu m$ to $20\mu m$, is plotted in Figure 6.2. The difference between the plane-

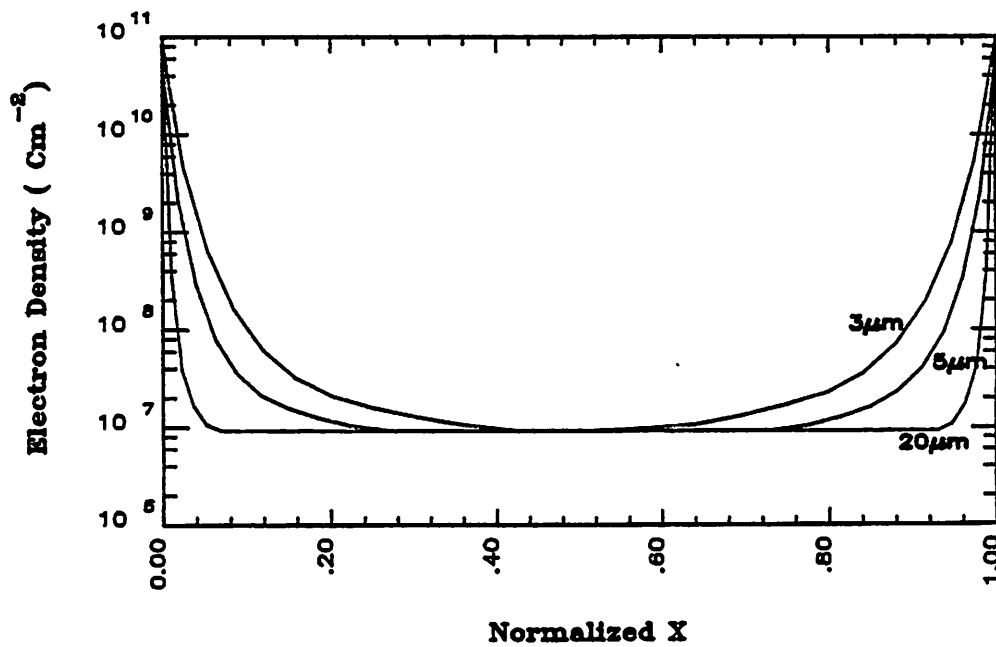
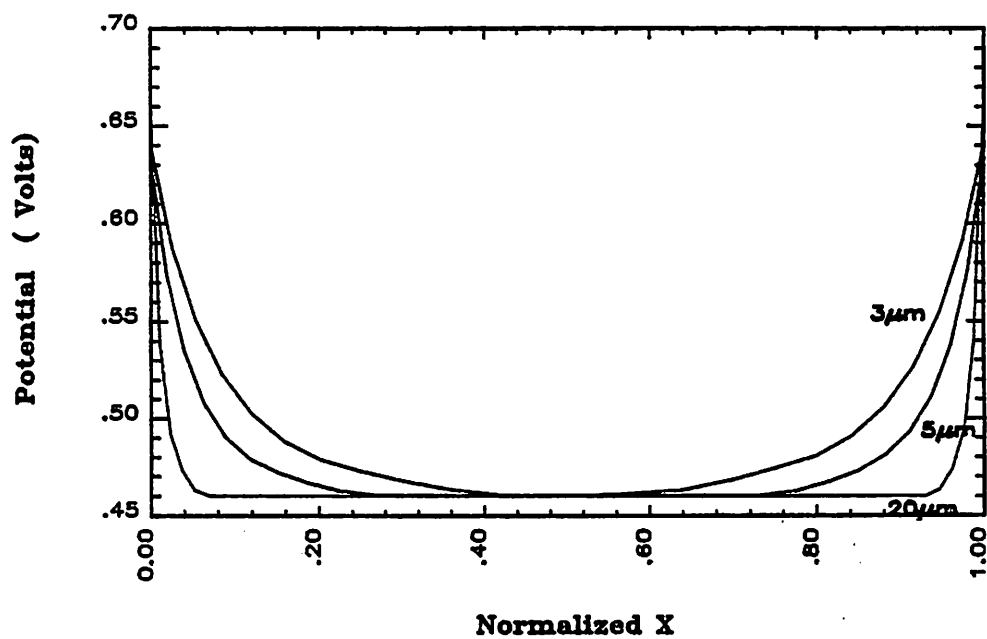


Figure 6.1 Surface Potential and Carrier Density versus Normalized Channel Lengths,

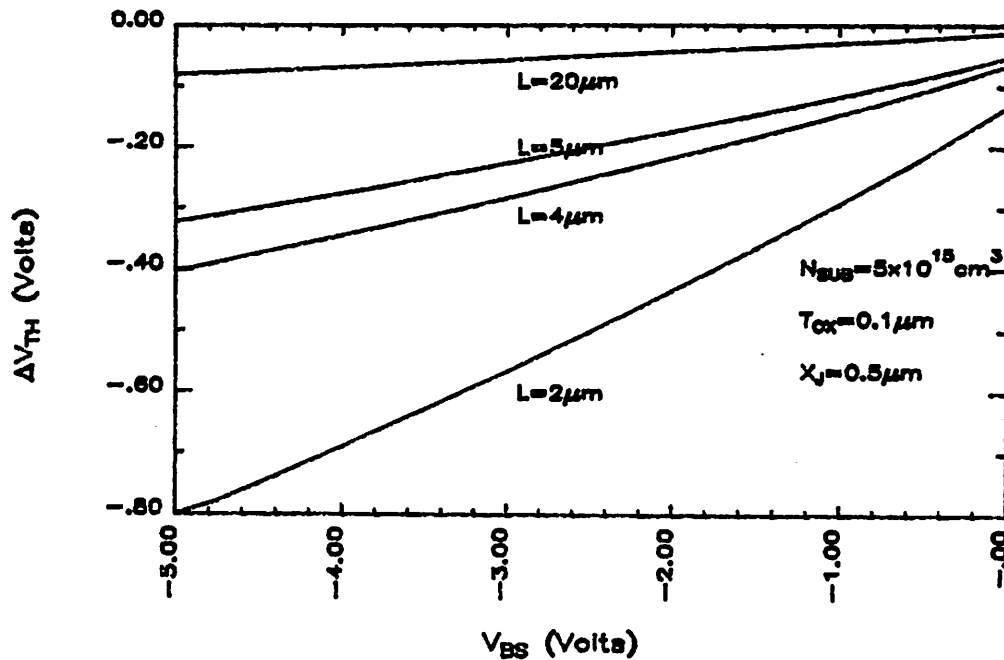


Figure 6.2 The V_{TH} Shift versus V_{BS} with Channel Length as Parameter,

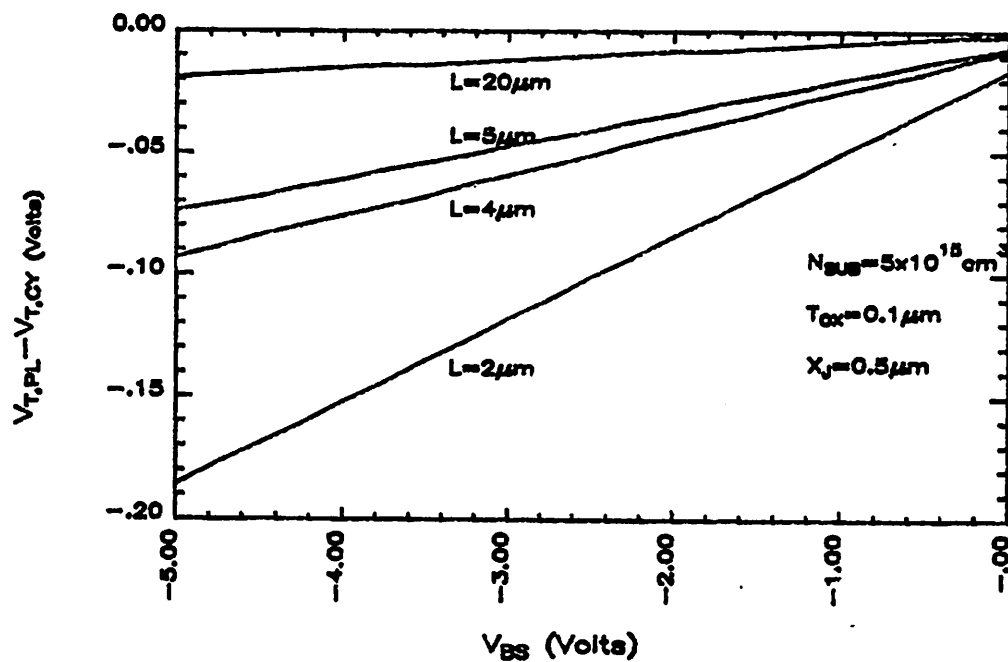


Figure 6.3 The V_{TH} 's of the Plane and Cylindrical Junction Approximations,

junction approximation [51] and the cylindrical-junction approximation [48] is plotted in Figure 6.3. This difference is important in the case of low V_{GS} operation in which the device characteristics are sensitive to the exact value of the threshold voltage. The difference increases as the deviation between the predicted depletion-region widths increases, i.e. when the substrate doping concentration is lower, the oxide thicker, and the junction made more shallow.

In the case of a shorter channel length, the source and drain depletion regions merge and the barrier maximum becomes a single point. The barrier height is lowered and can be further modulated by the drain voltage, as shown in Figure 5.2. An extra term which is linearly proportional to V_{DS} has been added to Equation (6.2). The proportional constant is inversely related to the oxide capacitance and the cube of the channel length [54]. Parameter η is designed to allow flexibility:

$$\Delta_L V_{TH} = \frac{\eta A}{C_{OX} L^3} V_{DS} \quad (6.4)$$

where A is an empirical constant whose value varies with the process parameters.

6.1.2. Narrow-Channel Effect

By assuming cylindrical distributions of the depletion charge at the edges, a correction factor can be formulated as:

$$\Delta_W V_{TH} = DELTA \frac{\pi \epsilon_s}{C_{OX} W} [\phi + V_{SB}] \quad (6.5)$$

Other edge effects, such as the existence of a field implant, non-planarity due to a LOCOS process, and the correction of the cylindrical field distribution, are included by introducing the empirical parameter, DELTA. This

parameter is characterized by threshold-voltage measurements.

6.1.3. The Model Equations

From the above, V_{TH} is formulated as:

$$V_{TH} = V_{FB} + \phi - F_D V_{DS} + \gamma F_S \sqrt{\phi - V_{BS}} + F_N [\phi - V_{BS}] \quad (6.6)$$

where F_D is the static-feedback coefficient:

$$F_D = \eta A \frac{L^{-3}}{C_{OX}} \quad (6.7)$$

A is an empirical constant:

$$A = 8.15 \times 10^{-22} \text{ (meterfarad)} \quad (6.8)$$

and gamma is the body-effect coefficient without any correction:

$$\gamma = \frac{\sqrt{2\epsilon_s q N_{SUB}}}{C_{OX}} \quad (6.9)$$

F_S is the correction factor due to the short-channel effect as defined in Equation (6.3). L_D is the lateral-diffusion length, W_P the depletion-layer width of a plane junction, and W_C the depletion-layer width of a cylindrical junction and:

$$\frac{W_C}{x_J} = d_0 + d_1 \frac{W_P}{x_J} + d_2 \left[\frac{W_P}{x_J} \right]^2 \quad (6.10)$$

where d_0 , d_1 and d_2 are empirical constants with the following values [48]: $d_0 = 0.0631353$, $d_1 = 0.8013292$, $d_2 = 0.01110777$. In Equation (6.6) F_N is the correction coefficient of narrow-channel effect:

$$F_N = \text{DELTA} \frac{\pi \epsilon_s}{C_{OX} W} \quad (6.11)$$

6.2. Basic Drain-Current Equation

The drain current can be expressed as:

$$I_{DS}^o(x) = WQ_{INV}(x)v(x) \quad (6.12)$$

where $N(x)$ is the carrier density per unit area at location x :

$$Q_{INV}(x) = C_{OX} [V_{GS} - V_{TH}(x)] \quad (6.13)$$

$v(x)$ is the carrier drift velocity:

$$v(x) = U \frac{dV(x)}{dx} \quad (6.14)$$

$V_{TH}(x)$ is the effective threshold voltage at location x :

$$V_{TH}(x) = V_{FB} + \phi(x) + \gamma\sqrt{\phi(x)} \quad (6.15)$$

Since the drain current is a constant independent of the location, Equation (6.12) can be integrated from the source to the drain to provide:

$$I_{DS}^o = \frac{W}{L} \int_0^{V_{DS}} Q_{INV}(x) dV(x) \quad (6.16)$$

The carrier density can be approximated by linearizing the expression of the effective threshold voltage with respect to the source:

$$V_{TH}(x) = V_{TH}(src) + [1 + F_B]V(x) \quad (6.17)$$

where

$$F_B = 0.5 \frac{\gamma}{2\sqrt{\phi} + V_{SB}} \quad (6.18)$$

The 0.5 factor is used to count the effect of the other higher order terms which are dropped for simplicity. The expressions of the carrier and current densities become:

$$Q_{INV} = C_{OX} [V_{GS} - V_{TH} - [1 + F_B]V(x)] \quad (6.19)$$

$$I_{DS}^o = \frac{W}{L} U C_{OX} \left[V_{GS} - V_{TH} - \frac{[1 + F_B]}{2} V_{DS} \right] V_{DS} \quad (6.20)$$

A similar expression has been developed by other workers [55].

The above equation is an approximation of the drain-current expression which has been widely used in text books [31,56]:

$$I_{DS}^o = \frac{W}{L} U C_{OX} \left[\left[V_{GS} - V_{FB} - \phi - \frac{V_{DS}}{2} \right] V_{DS} - \frac{2}{3} \gamma \left[\left[\phi + V_{DB} \right]^{\frac{2}{3}} - \left[\phi + V_{SB} \right]^{\frac{2}{3}} \right] \right] \quad (6.21)$$

These two equations differ in their linearization of the threshold-voltage expression. A comparison between Equations (6.20) and (6.21) is plotted in Figure 6.4 for the cases of $L = 5\mu m$, $W = 50\mu m$, $T_{OX} = 0.65\mu m$, $U_O = 600cm^2/V\text{-sec}$, $V_{TO} = 1V$ and $N_{SUB} = 5.0 \times 10^{15}cm^{-3}$ and $5.0 \times 10^{15}cm^{-3}$. A simpler expression based upon charge-control analysis [56] is also plotted in the same figure for comparison:

$$I_{DS}^o = \frac{W}{L} U C_{OX} \left[V_{GS} - V_{TH} - \frac{V_{DS}}{2} \right] V_{DS} \quad (6.22)$$

These three characteristics are approximately the same in the low V_{DS} range. The difference between the charge-controlled model and the text book model is much larger than that between the MOS3 and text book models. The characteristics at a higher V_{DS} are governed by second-order effects, such as the hot-electron effect, the current saturation, and the channel-length modulation. The basic current equation is critical only in the low V_{DS} operational range of a short-channel device. Thus Equation (6.20) can be applied to a small-geometry device without compromising accuracy.

The simplicity of Equation (6.20) leads to an explicit formulation of the saturation voltage which is derived later. Because the V_{DS} dependent term, η , in the threshold-voltage expression represents the average influence of the drain voltage upon the surface potential, it is treated as a constant throughout the integration in the derivation of current equation,

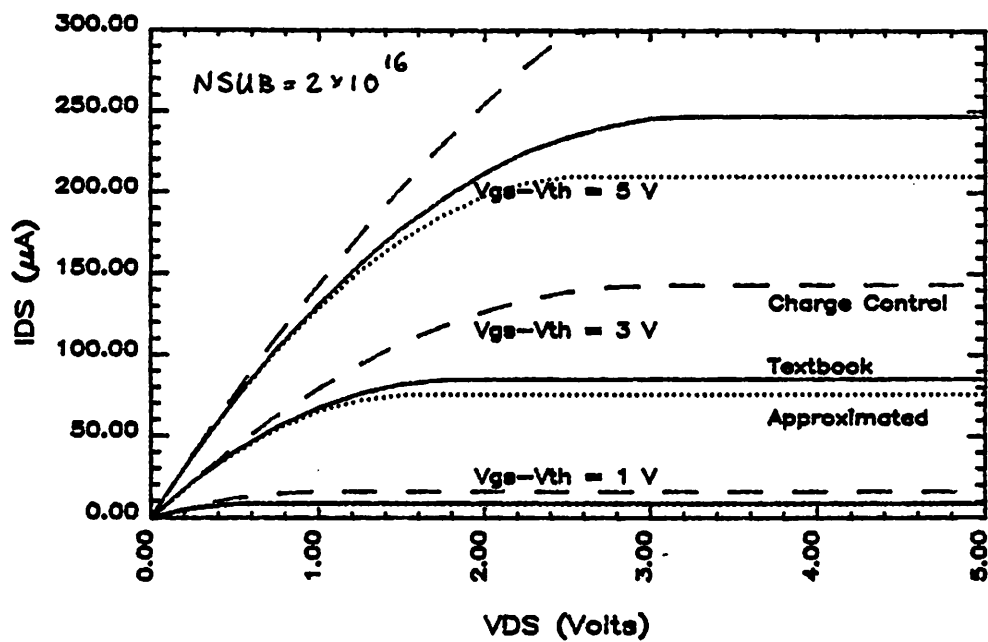
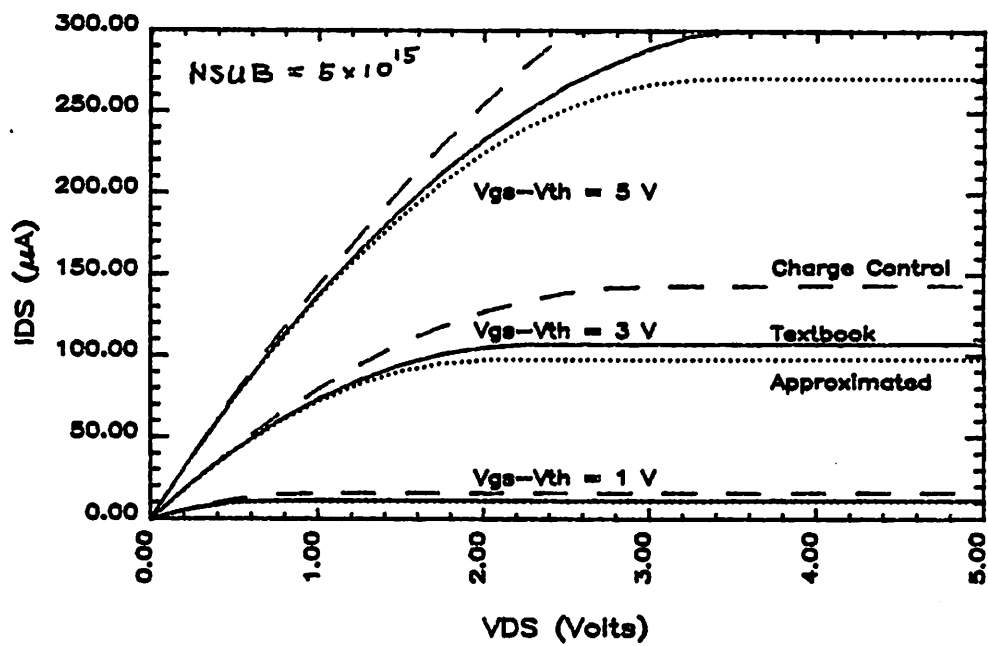


Figure 6.4 The Basic Current Equations with $N_{SUB} = 5.0 \times 10^{15}$ and $2.0 \times 10^{16} \text{ cm}^{-3}$,

6.3. Surface-Mobility Modulation by Gate Voltage

Surface mobility is directly proportional to the channel conductance of a device. Besides the lattice scattering [57] and the impurity scattering [58] which determine the value of bulk mobility, the surface mobility is further degraded by the mechanism of surface scattering [59] and interband scattering [60]. Considerable effort has been devoted to theoretical and experimental studies of the surface mobility. Nonetheless, the use of an empirical expression is still the most practical approach for device modeling in CADs.

The empirical equation of U_S used in the MOS3 is:

$$U_S = \frac{U_0}{1 + \theta(V_{GS} - V_{TH})} \quad (6.23)$$

For a comparison with the more elaborate formulation used in the MOS2 model in SPICE2 [61], the relationships between U_S and V_{GS} based upon these two expressions are plotted in Figure 6.5. These three plots show a very close match in the range of 10 V V_{DS} . Deviation is observed in both the low V_{DS} , 5 V, range, and the high V_{DS} , 20 V range. The plots demonstrate that the surface-mobility modulation effect can be matched by both empirical equations within a given operational range if the parameters are properly adjusted.

6.4. Velocity Saturation of Hot Electrons

Among various hot-electron effects [62], the saturation of hot-electron velocity has a direct impact on the characteristics of a short-channel device. It lowers the conduction current in the linear region and smooths the transition between the linear and saturation regions.

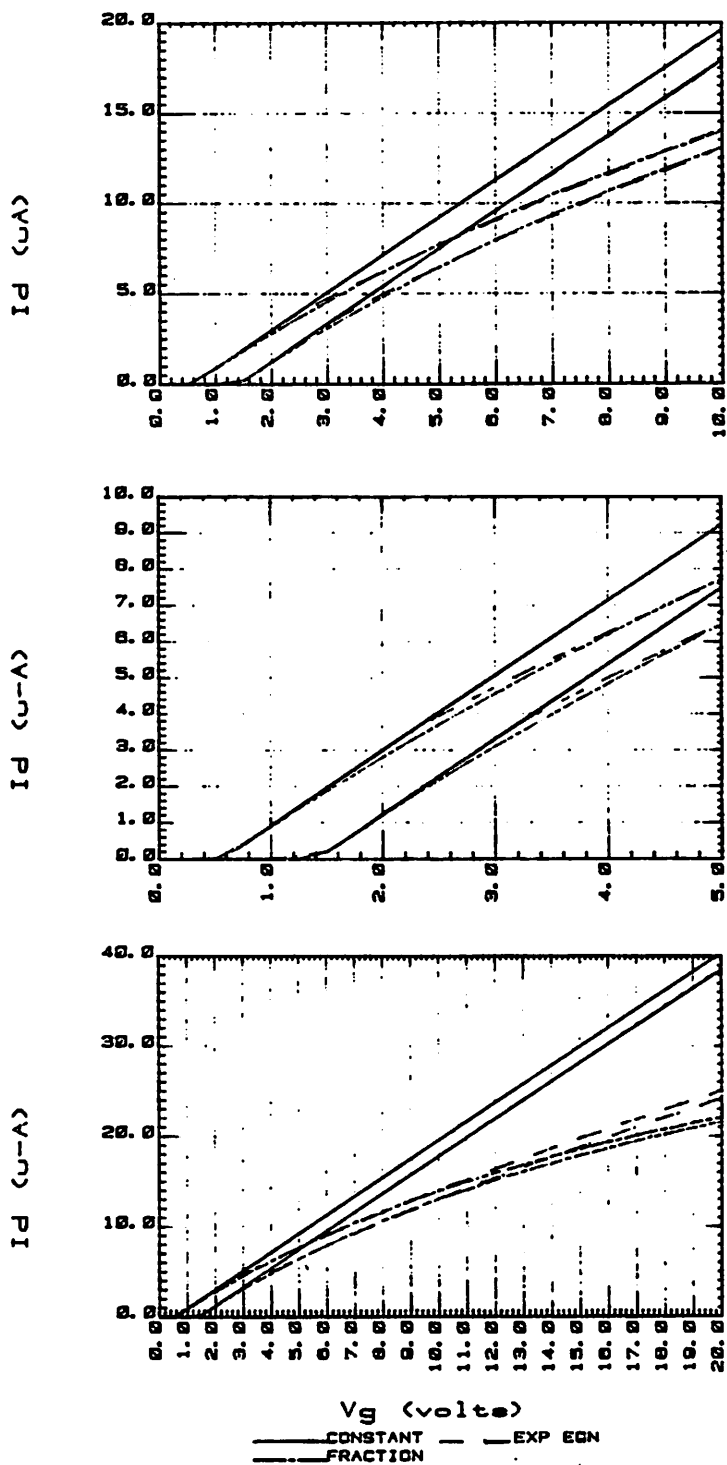


Figure 6.5 The Comparisons of Empirical Equations of Surface Mobility with Maximum $V_{DS} = 10V$, $5V$, and $20V$,

In a short-channel MOSFET, the lateral electric field in the channel is higher than that inside a long-channel device at the same operational bias. The effective mobility decreases and saturates when the electric field is stronger than the critical field. This relationship can be approximated by the following equation [63]:

$$U_{EFF}(x) = \frac{U_S}{1 + \frac{U_S}{V_{MAX}} \frac{dV}{dx}} \quad (6.24)$$

By substituting this expression in the basic current equation before carrying out the integration, the current equation becomes:

$$I_{DS} = \frac{I_{DS}^o}{1 + \frac{U_S}{V_{MAX}} \frac{V_{DS}}{L}} \quad (6.25)$$

The effective mobility can be expressed as:

$$U_{EFF} = \frac{U_S}{1 + \frac{U_S}{V_{MAX}} \frac{V_{DS}}{L}} \quad (6.26)$$

The effective mobility is plotted in Figure 6.6 as a function of V_{DS} . This effect has been interpreted as either a higher effective threshold voltage [64] or an effective feedback resistance [65].

6.5. Saturation Voltage

In a short-channel MOSFET the drain current saturates when the carrier velocity approaches its maximum [31], V_{MAX} , instead of approaching the channel pinch-off condition as it does in a long-channel devices. When the carrier velocity saturates, the current can be approximated as:

$$I_{DS}^o = Q_{INV}(drain)V_{MAX} \quad (6.27)$$

By substituting the expressions (6.19) and (6.20) in the above equation, it

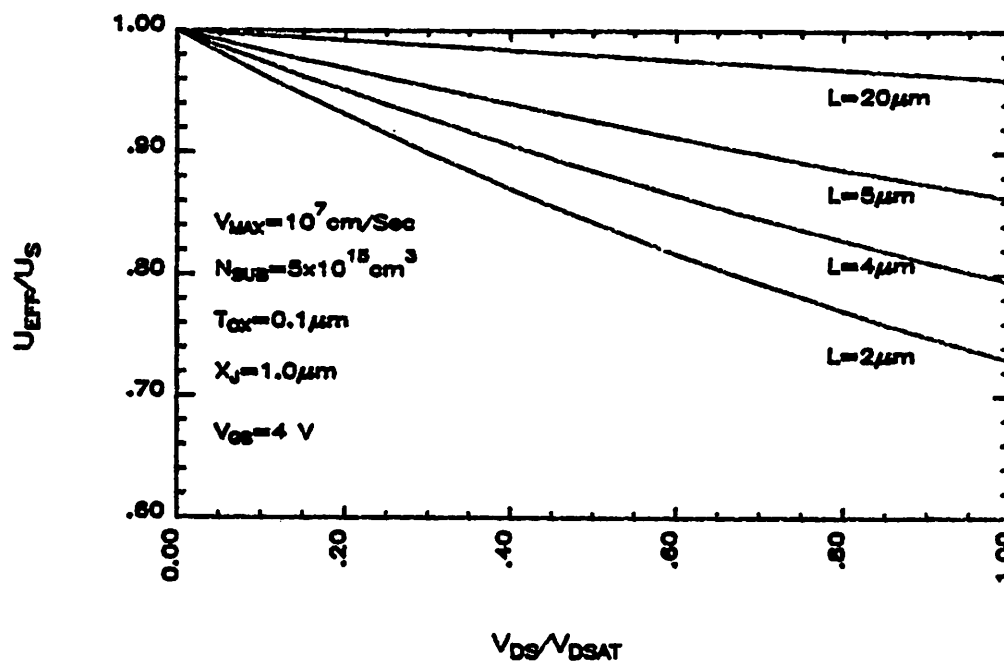


Figure 6.6 The Hot-Electron Effects on the Surface Mobility,

yields:

$$WC_{OX} \left[V_{GS} - V_{TH} - \left[1 + F_B \right] V_{DS,sat} \right] V_{MAX} = \quad (6.28)$$

$$\frac{W}{L} U_S C_{OX} \left[V_{GS} - V_{TH} - \frac{1 + F_B}{2} V_{DS,sat} \right] V_{DS,sat}$$

$V_{DS,sat}$ is derived from the above equation:

$$V_{DS,sat} = \frac{V_{GS} - V_{TH}}{1 + F_B} + \frac{V_{MAX}L}{U_S} - \sqrt{\left(\frac{V_{GS} - V_{TH}}{1 + F_B} \right)^2 + \left(\frac{V_{MAX}L}{U_S} \right)^2} \quad (6.29)$$

$V_{DS,sat}$ is dependent upon V_{DS} through V_{TH} . At the limit of infinite V_{MAX} , this equation can be rearranged as follows:

$$V_{DS,sat} = \frac{V_{GS} - V_{TH}}{1 + F_B} + \frac{V_{MAX}L}{U_S} \left[1 - \sqrt{1 + \left(\frac{V_{GS} - V_{TH}}{1 + F_B} \frac{U_S}{V_{MAX}L} \right)^2} \right] \quad (6.30)$$

By only taking the first-order term in the Taylor series expansion, the term of square root can be simplified and the above equation becomes:

$$V_{DS,sat} = \frac{V_{GS} - V_{TH}}{1 + F_B} - \frac{U_S}{2V_{MAX}L} \left[\frac{V_{GS} - V_{TH}}{1 + F_B} \right]^2 \quad (6.31)$$

$V_{DS,sat}$ approaches to $\frac{V_{GS} - V_{TH}}{1 + F_B}$ which is the maxima of the current equation and corresponds to the channel pinch-off condition of a long-channel device.

In the derivation of $V_{DS,sat}$, Equation (6.20) is used instead of Equation (6.25). As pointed out in Murphy's work [64], if the exact expression is used, the velocity "pinch-down" condition is equivalent to the channel "pinch-off" condition. The resulting saturation voltage, $V_{DS,sat}^o$, is the maximum of the basic current equation in which the slope of I_{DS} is zero:

$$V_{DS,sat}^o = \frac{LV_{MAX}}{U_S} \left[\sqrt{1 + \frac{2U_S}{V_{MAX}L} \frac{V_{GS} - V_{TH}}{1 + F_B}} - 1 \right] \quad (6.32)$$

$V_{DS,sat}^o$ is higher than $V_{DS,sat}$. From the view point of CAD applications, the zero-slope point is undesirable because the output conductance of a short-channel device is not zero. Equation (6.28) is equivalent to an approximation of the velocity-field relationship by two straight lines joined at the

saturation point, as shown in Figure 6.7. A comparison of saturation voltages based upon these two definitions is plotted in Figure 6.8 for the cases of $2\mu\text{m}$ and $5\mu\text{m}$ respectively. The discrepancy between $V_{DS,sat}$ and $V_{DS,sat}^o$ increases as V_{GS} increases.

6.6. Channel-Length Modulation

As V_{DS} gets larger than $V_{DS,sat}$, the point at which the carrier velocity begins to saturate moves toward the source, and the effective channel length is reduced. The formulation of the channel-length shortening factor, ΔL , is based upon Baum's theory [66] :

$$\Delta L = \sqrt{\left(\frac{E_P}{2B}\right)^2 + \kappa\left(\frac{V_{DS} - V_{DS,sat}}{B}\right)} - \frac{E_P}{2B} \quad (6.33)$$

$$I_{DS} = I_{DS,sat} \frac{L}{L - \Delta L} \quad (6.34)$$

where E_P is the lateral field at channel pinch-off point, and coefficient B is:

$$B = \frac{1}{X_D^2} \quad (6.35)$$

By making the slope of the I_{DS} -versus- V_{DS} characteristics continuous at $V_{DS} = V_{DS,sat}$, the expression E_P becomes:

$$E_P = \frac{I_{DS,sat}}{G_{DS,sat} L} \quad (6.36)$$

$I_{DS,sat}$ and $G_{DS,sat}$ are the drain current and the drain conductance at saturation voltage, respectively.

The point at which the velocity begins to saturate differs from the channel pinch-off point at which the free carriers begin to be depleted. $V_{DS,sat}$ is the voltage at the velocity-saturation point while E_P is the lateral field at the channel pinch-off point. Therefore, the voltage across the depleted surface should be less than $V_{DS} - V_{DS,sat}$. The empirical parameter κ is introduced to

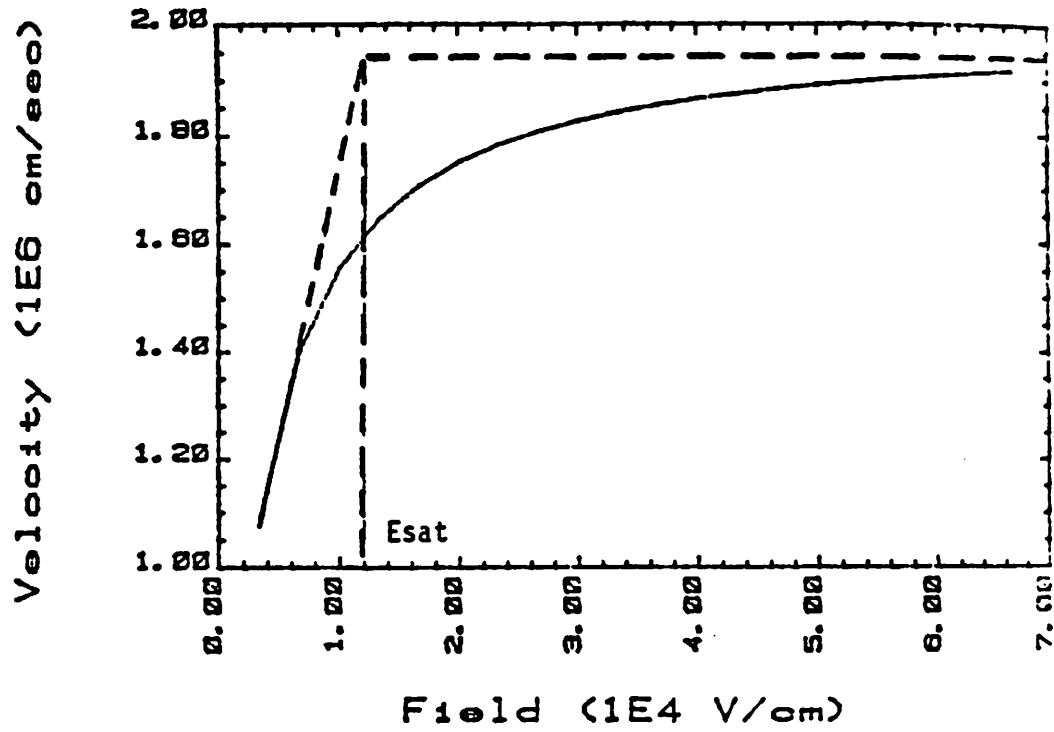


Figure 6.7 The Relationship between the Velocity and the Field Strength,

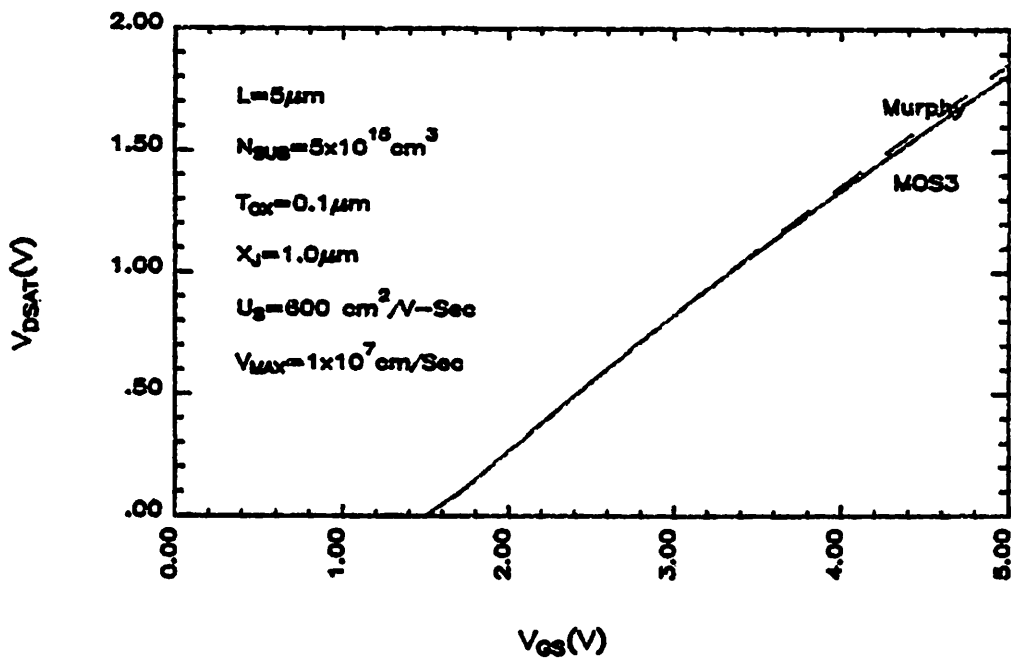
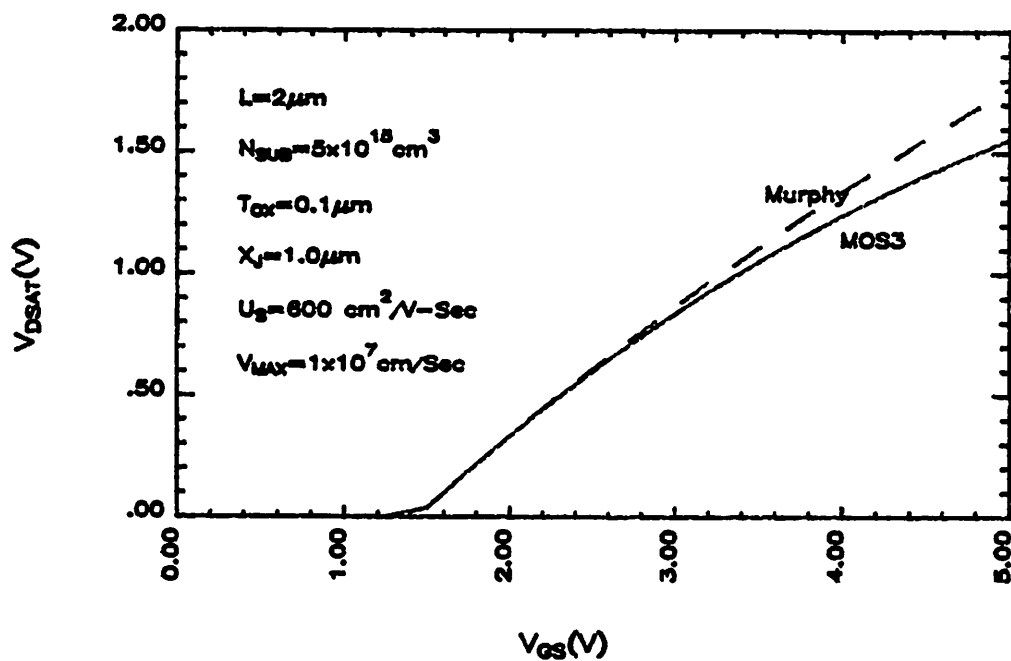


Figure 6.8 The $V_{DS,sat}$'s Based upon Different Definitions for the cases of $L = 2\mu\text{m}$ and $5\mu\text{m}$,

include this effect.

6.7. Capacitance Model with Charge Conservation

The companion capacitance model is based upon the charge-conservation concept [53] which is critical for the simulation of circuit operations depending upon charge transfer, for example, in switched capacitance circuits.

The total amount of charge residing on the gate can be formulated as:

$$Q_G = W \int_0^L Q_g(y) dy \quad (6.37)$$

$$= \frac{U_S W^2}{I_{DS}} \int_0^{V_{DS}} Q_g(V_y) Q_c(V_y) dV_y \quad (6.38)$$

where Q_g is the gate charge per unit area and Q_c the channel charge per unit area:

$$Q_g = C_{OX} \left[V_{GS} - \left[V_{FB} + \phi - F_D V_{DS} \right] \right] \quad (6.39)$$

$$Q_c = -C_{OX} \left[V_{GS} - V_{TH} - \left[1 + F_B \right] V_y \right] \quad (6.40)$$

The integration if carried out yields:

$$Q_G = W \times L \times C_{OX} \left[V_{GS} - \left[V_{FB} + \phi - F_D V_{DS} \right] - \frac{V_{DS}}{2} + \frac{1 + F_B}{12F_I} V_{DS}^2 \right] \quad (6.41)$$

where

$$F_I = V_{GS} - V_{TH} - 1 + F_B/2V_{DS} \quad (6.42)$$

Similarly, the total bulk charge, Q_B , can be obtained:

$$Q_B = -W \times L \times C_{OX} Q_B^\circ \quad (6.43)$$

where

$$Q_B^\circ = \gamma F_S \sqrt{\phi + V_{SB}} + F_N (\phi + V_{SB}) + \frac{F_B}{2} V_{DS} - \frac{F_B(1 + F_B)}{12F_I} V_{DS}^2 \quad (6.44)$$

The charge-neutrality condition requires that the total channel charge be:

$$Q_C = - [Q_G + Q_B] \quad (6.45)$$

which is distributed between the source and the drain.

There are three charge quantities. Each of them has three associated derivatives which are the capacitive elements in the circuit model. Only six of these nine capacitance components are independent because Q_G , Q_B and Q_C are correlated with each other.

The resulting C-V characteristics, based upon the parameters listed in Table 6.1, is plotted in Figure 6.9, together with the corresponding C-V curves predicted by MOS2 [15] with the same parameters. Because of the linearization employed in MOS3, the results differ in the capacitive components which are related to the channel charge.

6.8. The Comparison Between MOS2 and MOS3

MOS3 is a semi-empirical model developed specifically for small-geometry devices. This section is intended to demonstrate the validity and performance of MOS3 through device characterizations and test-circuit simulations. The MOS2 model [15], which is based upon approximations for and analyses of devices with channel lengths greater than $2\mu m$, is used as the test vehicle for comparison. Both MOS2 and MOS3 are implemented in SPICE2G. Although they have many common parameters, different values of the mobility-related parameters must be used to produce approximately the same characteristics. For example, parameter VMAX (V_{MAX}) has no effect on the characteristics in the linear region simulated by MOS2, while it lowers the effective mobility in the medium V_{DS} range when simulated by MOS3. In order to get a close approximation, MOS2 requires a lower value

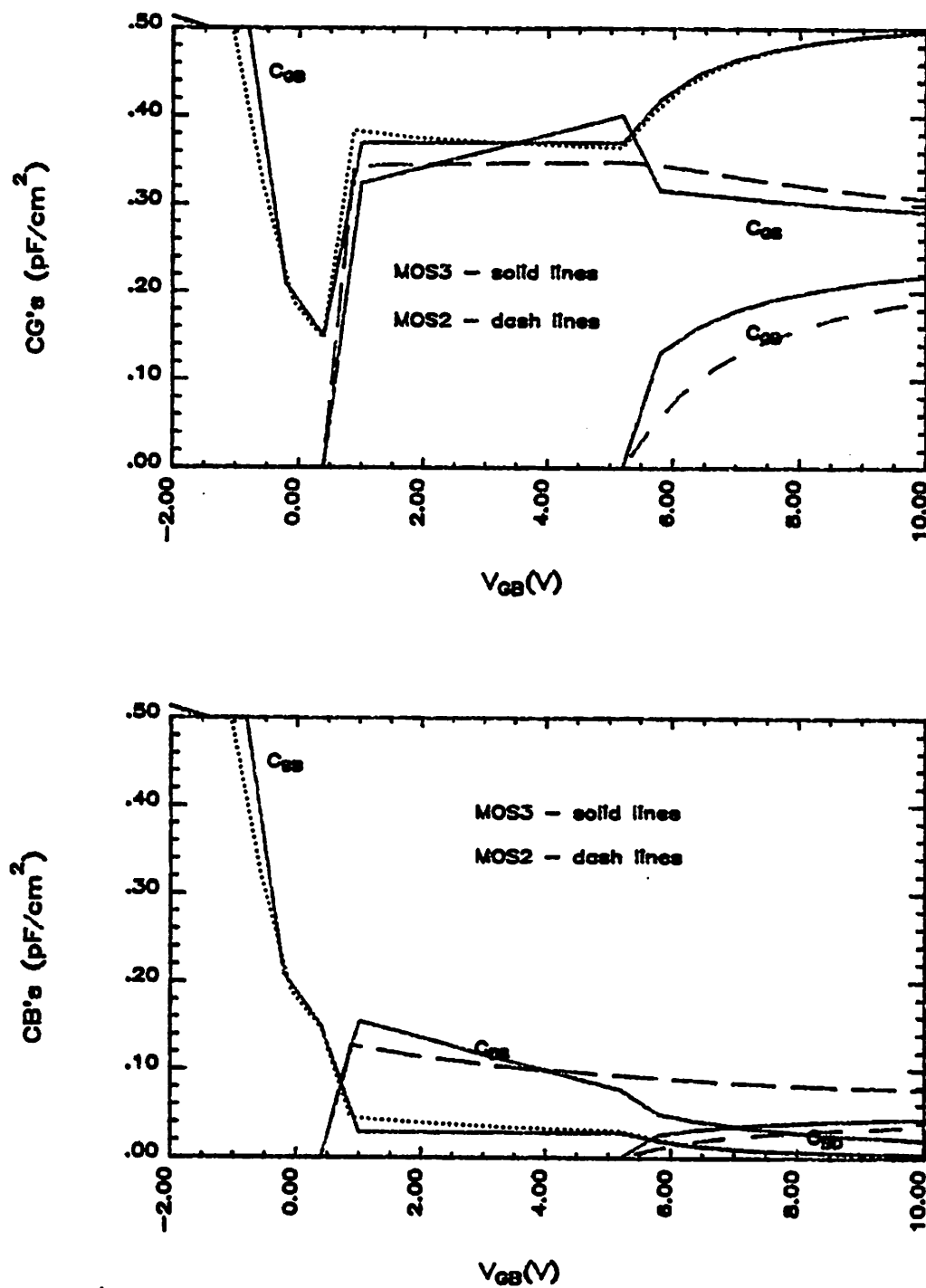


Figure 6.9 The Gate and Substrate Capacitances in MOS2 and MOS3,

of the parameter U_0 .

The differences between MOS2 and MOS3 are:

- (a) The basic current equation used in MOS3 is an approximation of that of MOS2;
- (b) Different empirical equations of surface-mobility modulation are used;
- (c) The static-feedback effect is modeled by drain-induced barrier lowering in MOS3 and by charge sharing between the drain and the gate in MOS2;
- (d) Parameter V_{MAX} lowers both the effective mobility and the saturation voltage in MOS3 but affects only the saturation voltage in MOS2;
- (e) The junction curvature effect is included in the threshold-voltage equation of MOS3 but the junctions are treated as plane junctions in MOS2.

Two devices are characterized by both MOS2 and MOS3 for comparison. One is long with a layout channel length of $20\mu m$; the other one is short with layout channel length of $2.3\mu m$, the effective channel length after side-diffusion correction is $1.6\mu m$. The two devices reside on the same chip and have the same width, $50\mu m$. Their simulated and measured characteristics are plotted in Figures 6.10 and 6.11 respectively, and the parameter values are listed in Table 6.1:

10/1.6 DEVICE AT $V_{BS}=0$

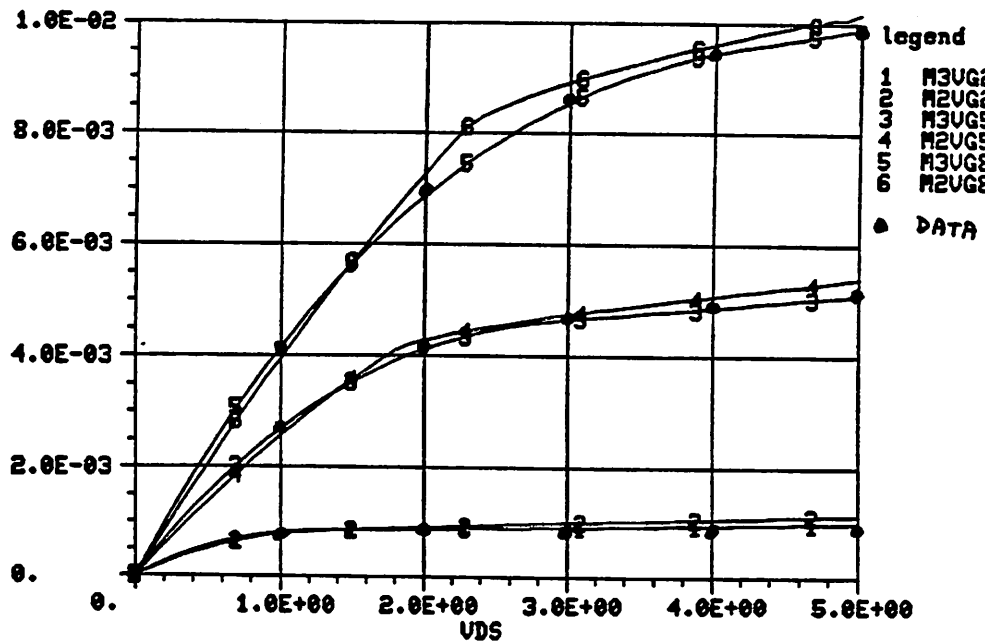
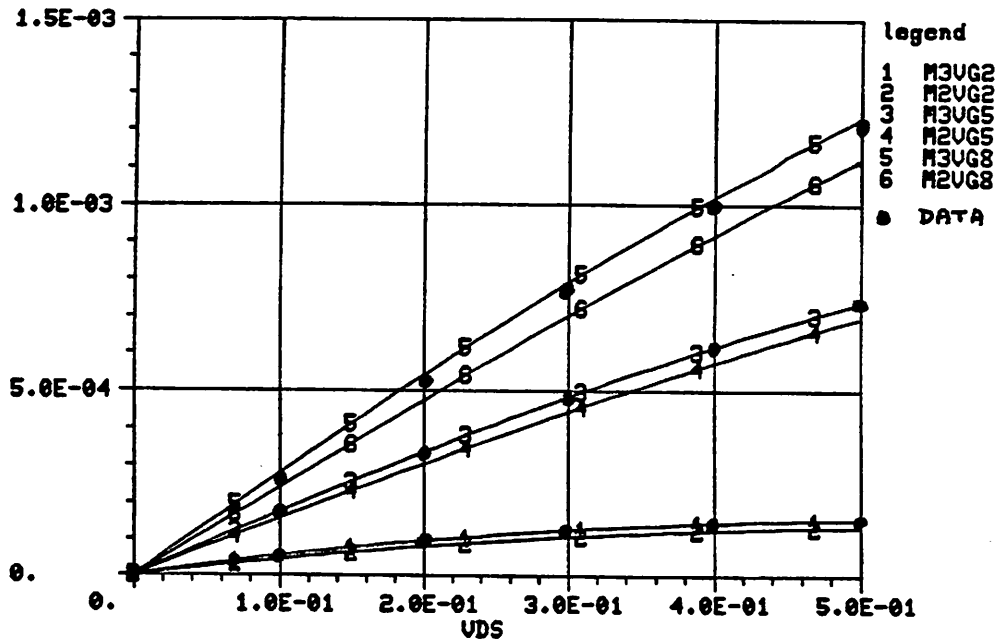


Figure 6.10 The Experimental Measurements, the MOS2 and MOS3 Models in the Low and High V_{DS} Ranges of the Short-Channel Device, with $V_{BS} = 0V$,

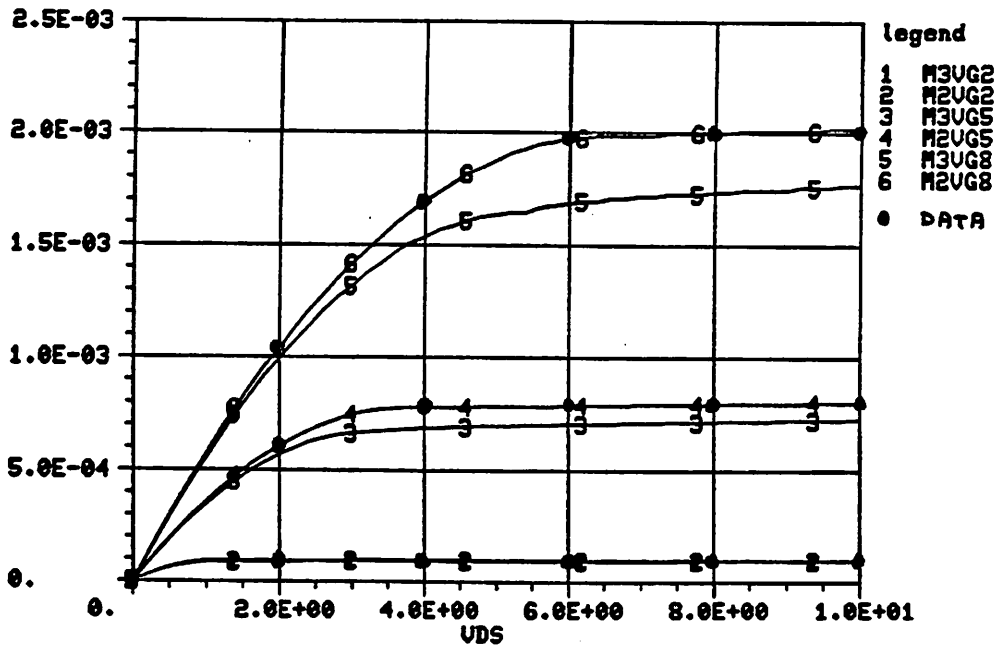
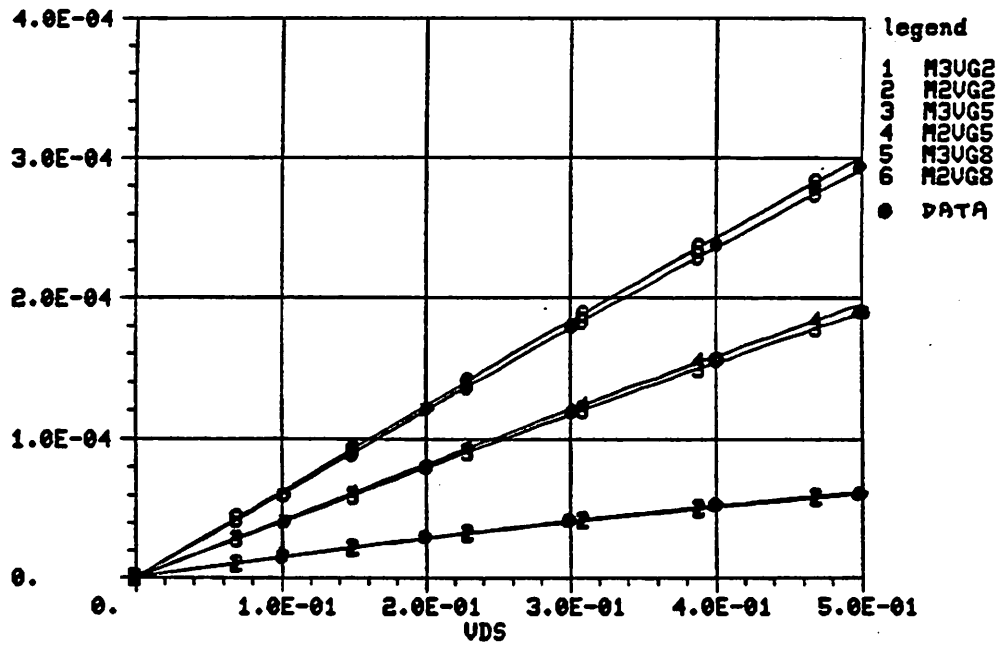


Figure 6.11 The Experimental Measurements, the MOS2 and MOS3 Models in the Low and High V_{DS} Ranges of the Long-Channel Device, with $V_{BS} = 0V$,

Table 6.1				
Param.	Device No.1		Device No.2	
	MOS3	MOS2	MOS3	MOS2
W(um)	50	50	50	50
L(um)	2.3	2.3	20	20
XJ(um)	0.5	0.5	0.5	0.5
LD(um)	0.35	0.35	0.35	0.35
VTO(V)	0.452	0.452	0.452	0.452
TOX(um)	0.065	0.065	0.065	0.65
NSUB(cm-3)	1.85E11	1.85E11	1.85E11	1.85E11
UO(cm ² /V-s)	578	450	790	720
VMAX(M/s)	20E4	6E4	-	-
theta	0.06	-	0.045	-
eta	0.035	-	0	-
KAPPA	1.0	-	1.0	-
UEXP	-	0.24	-	0.20
UCRIT(V/M)	-	1.2E6	-	1.5E6
NEFF	-	7	-	1

Table 6.1 Device Model Parameters

All the process parameters except those related to mobility are the same. In the case of the short-channel device, MOS3 can fit both the high- and low-current ranges consistently while MOS2 can fit only the high-voltage range. MOS3 requires a higher UO and a higher VMAX, $\frac{V_{MAX}}{U_s}$, which is equivalent to a saturation field of $3.46 \times 10^4 V/cm$. This corresponds to the field in which the velocity begins to saturate. The values of VMAX and UO used in MOS2 yield a saturation field of $1.3 \times 10^4 V/cm$, which corresponds to the field at the corner of the velocity-saturation curve. This is the result of the different assumptions used in the models. The discrepancy between the predictions by the MOS3 model and the measurements of the long-channel device is

expected because the simulated characteristics of a long-channel device are dominated by the basic current equations. MOS2, whose basic current equation is based upon a more thorough analysis, is able to fit the long-channel device in both high and low current ranges consistently while MOS3 can fit only the low or high current range by using different mobility-related parameters.

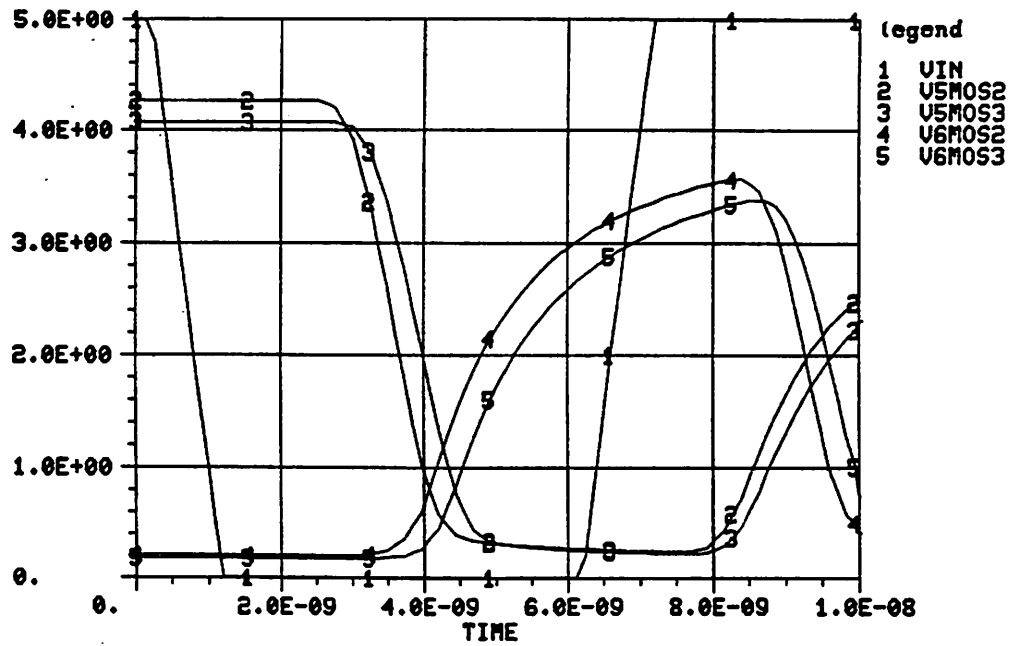
With devices of matched characteristics, several test circuits have been simulated by both models using SPICE2G.1. The inputs to SPICE2 are listed in Appendix D. The output waveforms are plotted in Figures 6.12(a) through (d). Even with the carefully chosen parameters, these two models do not give identical device characteristics, although the results are similar. The simulation statistics are compared in Table 6.2:

Table 6.2						
Circuit Name	Analysis Type	X'tors MOS3	Iteration No.		CPU (sec)	
			MOS2	MOS3	MOS2	MOS3
Bootinv	Op Point	5	44	42	1.48	1.95
	Transient	-	235	280	9.54	15.77
Invchn	Op point	10	48	48	2.49	3.43
	Transient	-	208	306	14.94	26.69
Mosmem	Op point	12	164	34	9.25	3.21
	Transient	-	248	389	20.57	36.06
Ratlog	Op point	6	25	26	1.11	1.53
	Transient	-	778	648	36.47	40.13

Table 6.2 Simulation Statistics

The results show that for most of the circuits, the MOS3 model is up to 40% faster in computation than MOS2.

(a) INUCHN - FIVE STAGE SATURATED INVERTER CHAIN



(b) RATLOG - RATIOLESS DYNAMIC LOGIC

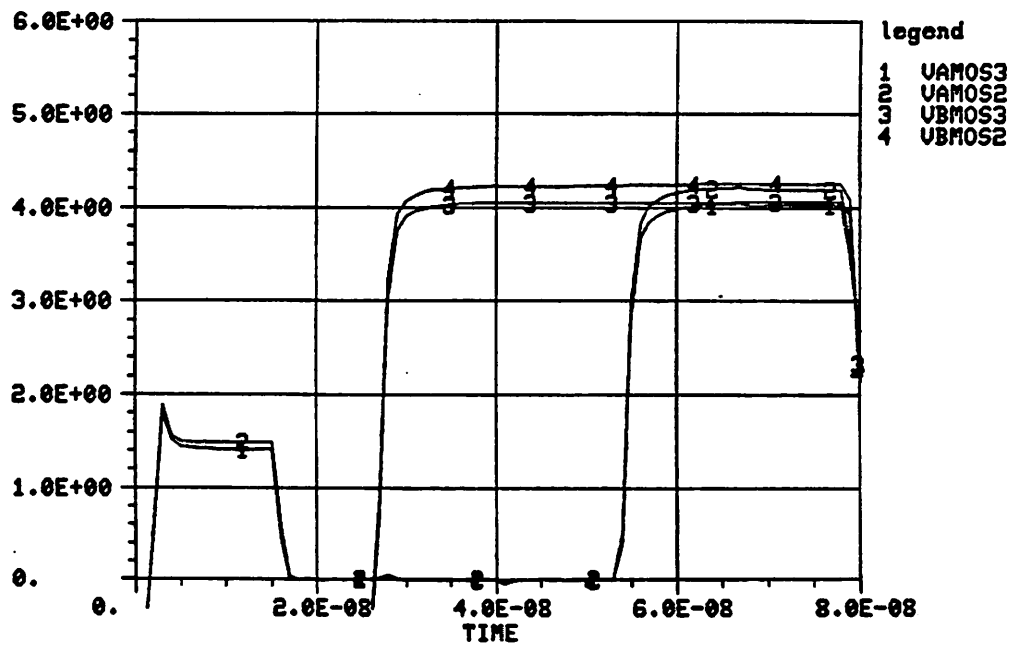
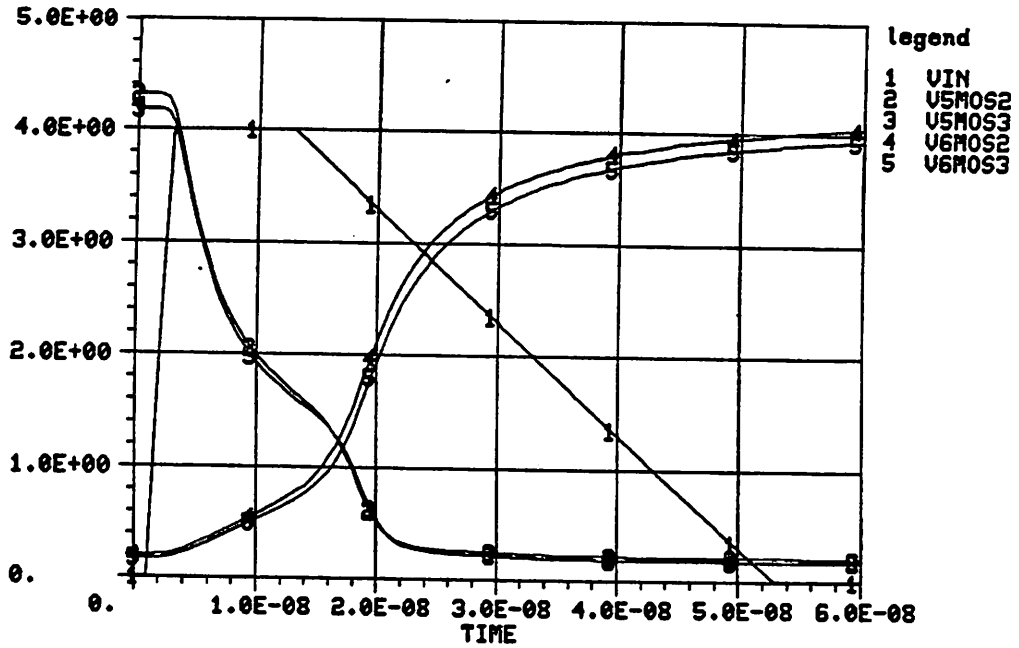


Figure 6.12 The Simulation Results of Test Circuits using the MOS2 and MOS3 Models, (a) Five-Stage Inverter-Chain, (b) Ratioless Logic Circuit of Sift-Register,



(d) BOOTINU - BOOT STRAPPED DOUBLE INVERTER

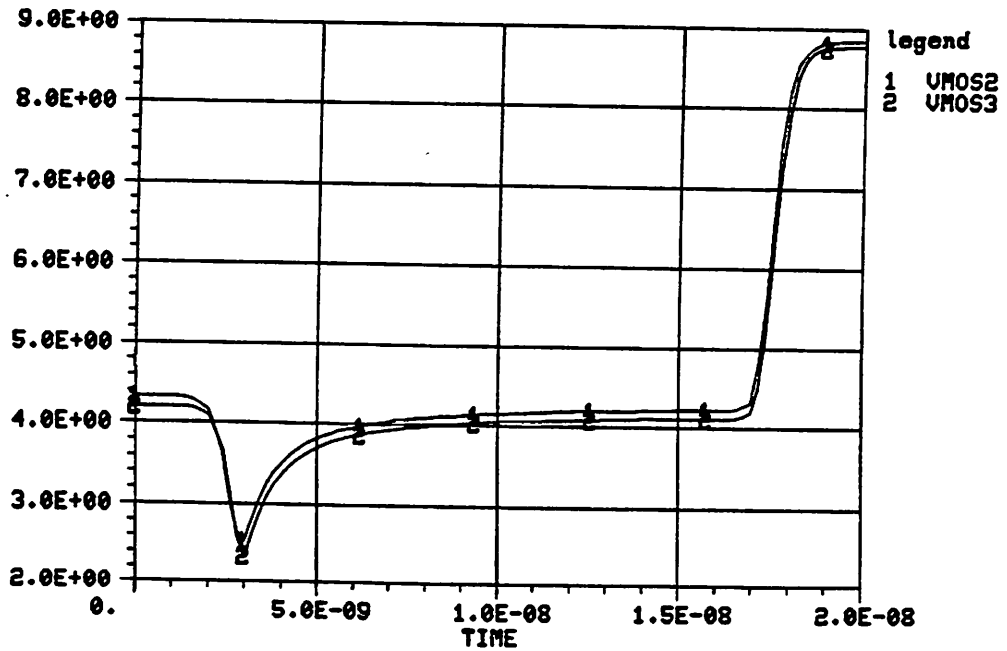


Figure 6.12 (c) Six-Transistor Memory Cell, (d) Boot-Strap Inverter,

CHAPTER 7

Summary

This analysis of MOSFETs emphasizes possible problems due to quantum-mechanical effects, the unification of strong- and weak-inversion regions and the modeling of small-geometry devices. The first two problem areas concern the modeling of MOSFETs in general. The modeling need for small-geometry devices is due to the recent advances in integrated-circuit processing which have led to today's VLSI chips.

The quantum-mechanical effects are attributed to both the degeneracy of the surface carrier population, which can be described only by Fermi-Dirac statistics, and the wave property of surface carriers in degeneracy, which is governed by the Schrödinger equation. Numerical evaluations of the drain current, the channel conductance, etc. based upon quantum-mechanical statistics, demonstrate that quantum-mechanical statistics alone do not result in a significant deviation in device characteristics within a practical operational voltage range. The onset voltage of degeneracy is at the high end of the voltage range of most practical applications. Though the differences in device characteristics induced by the wave property may be large, these differences can be absorbed in the empirical expression of surface mobility, whose variations are much greater in the practical operational range.

Existing MOSFET models which are valid for both the strong- and weak-inversion regions require time-consuming iterative solutions. The other models are valid in either strong- or weak-inversion region. The approach presented in Chapter 3 joins the weak- and strong-inversion regions by recognizing the existence of a transition region. It proves to be an

efficient approximation of the iterative solution.

Program TWIST was developed to simulate the characteristics of weak inversion and weak-injection punchthrough of short-channel MOS devices by solving the two-dimensional Poisson equation. The program is sufficiently fast in its analysis to allow reasonable interaction with a process or device designer as the simulation is performed. In a working hierarchy of CAD tools, structural and impurity parameters can be obtained from process simulators. TWIST can then be used to optimize all the aspects of barrier-controlled operations and as a pre-selector for structures to be simulated by a more elaborate two-dimensional simulation program to obtain high-current device characteristics.

The analysis of the punchthrough phenomena involves both theoretical analyses and two-dimensional device simulations. The formation and characteristics of the injection barrier are studied and the equation of the onset voltage of punchthrough is derived assuming a uniform substrate doping concentration. The experimental data supports the derived equation.

The MOS3 model has been developed and implemented in the circuit simulation program SPICE2 to address the features of small-geometry MOSFETs and to permit the effective simulations of integrated circuits containing small-geometry MOSFETs. The model equations are formulated to allow easy and automatic parameter extraction, a property which is as critical as the accuracy of the model itself. A comparison of the MOS2 and MOS3 models proves that the MOS3 model is accurate for small-geometry MOSFETs.

In the era of LSI and VLSI, the emphasis of modeling should be placed upon the small-geometry devices. The two-dimensional device simulation is an indispensable tool for the study of micron or submicron devices. In the course of expanding Program TWIST to include the solution of the current-

continuity equation, the attention must be put on finding and implementing both efficient algorithms of numerical solutions and adequate physical models of various high-current effects. The impurity profile in a small-geometry device critically affects device characteristics. The thermal redistribution in both one and two dimensions, must be considered in the generation of impurity profile. This profile dependence will be an important part of the future study of both two-dimensional device simulation and circuit-simulator oriented models. Although the onset of punchthrough is described in this thesis, a complete model of punchthrough conduction remains to be formulated. More research is needed in this area.

APPENDIX A

TWIST User's Guide

TWIST is a program for the "Two-dimensional Interactive Simulation of MOS Transistors" in weak inversion and/or weak injection. The device geometry and doping profile as well can be entered either through the console or a parameter file. The doping profile can be defined analytically by specifying process parameters or numerically by using the results from Program SUPREM. The resulting impurity concentration, carrier concentration, potential, and field distributions are either displayed as three-dimensional graphs or output as numerical tables. The interactive feature of TWIST allows maximum flexibility to the user.

Except for numerical parameters, which include the values of device dimension, impurity concentration, voltage, etc., soft (special purpose) keys on the keyboard are used to facilitate the question-and-answer session. Keys No.7 and No.8 are always designated as Yes and No, respectively. The definitions of other keys are displayed with the accompany questions. If an answer is entered from the keyboard, instead of the soft keys, the first character of the alphabetical answers must be in the upper case.

In the following, the procedure of using TWIST is explained step by step. All the information displayed by TWIST is shown in *italics* in the same sequence as prompted by TWIST. f7 and f8 are the abbreviations for keys No.7 and No.8 respectively.

1. Input Options

REQUEST->

Input from the console (Yes=f7/No=f8) ?

Yes-> TWIST will ask for the name of the parameter file, read the geometry and profile parameters from it, and branch to Section 5 if SUPREM results are used; otherwise it will proceed to Section 6. The format of the parameter file is detailed at the end of this guide.

No-> Parameters will be requested on the console.

2. Geometry Parameters

REQUEST->

Drawn channel length (μm) ?
Lateral span of source (μm) ?
Lateral span of drain (μm) ?
Oxide thickness: gate <> and field <> (μm) ?
Gate oxide location: from <> to <> (μm) ?
Span of oxide ramp (μm) ?
Drawn gate location: from <> to <> (μm) ?
Depth of the simulated structure (μm) ?

All the entries should be in units of μm . The source junction is defined as the origin of the coordinates.

3. Profile Options

REQUEST->

"Use SUPREM output (Yes=f7/No=f8) ?"

Yes-> The profile is generated by the interpolation of SUPREM results.

No-> Parameters of analytically generated profiles are entered from the console.

4. Profile Parameters

The profile can be tailored by up to three implantation steps, i.e. overall, selective and source/drain implants. The overall implantation covers the entire structure; the selective implantation can be directed into either a specified window or over the entire structure; the source/drain implantation goes only into the source/drain windows. The two-dimensional redistribution of drive-in is considered only for the selective and the source/drain implantations.

4.1. Substrate

REQUEST->

*Substrate dopant ?
Substrate concentration (in unit of 1E15 cm-3) ?*

4.2. Ion Implantation

REQUEST->

*Any overall implant (Yes=f7/No=f8) ?
Any localized implant (Yes=f7/No=f8) ?
Any source/drain implant (Yes=f7/No=f8) ?*

Yes-> Invoke the corresponding ion-implantation step.

No-> Skip the corresponding ion-implantation step.

The implant dopant can be entered either by the species (B/As/Ph/Sb), or by the type (-/+), where - stands for N-type and + for P-type. If a species is used, the associated drive-in process is characterized by the temperature and the time. Otherwise, the drive-in process is characterized by the diffusivity and the time.

REQUEST->

Implant parameters: Range(μm) <> Stndv(μm) <> Dose(cm^{-2}) ?
Diffusion coefficient at drive-in temperature (cm^2/sec) ? (optional)
Drive-in temperature ($^{\circ}\text{C}$) ?
Drive-in time (minutes) ? (optional)

A table of computed parameters is displayed at this point. For example,

...profile parameters:
diff const = $4.75\text{E}-15$ (cm^2/sec) peak conc = $-3.85\text{E}+15$ (cm^{-3})
jct depth = $2.19\text{E}-05$ (cm) average conc = $-4.58\text{E}+15$ (cm^{-3})

where jct is the abbreviation of junction, diff of diffusion, and conc of concentration.

5. Profile Based on SUPREM Results

5.1. Substrate

REQUEST->

Substrate dopant ?
Uniform substrate (Yes=f7/No=f8) ?

Yes-> Substrate concentration will be requested.

Substrate concentration (in unit of $1\text{E}15 \text{ cm}^{-3}$) ?

No-> File name and column index will be requested and the substrate profile is treated as the result of the overall implantation (see next section).

*Data file name ?
Which column ?*

The background concentration will be extracted and displayed:

*Non-uniform substrate with background concentration
= $-7.500E+14\text{cm}^{-3}$*

5.2. Ion-Implantation

REQUEST->

*Implant dopant ?
Implant STNDV(μm) ?
Data file name ?
Which column ?*

A table of the estimated profile parameters is displayed at this point.

*...profile parameters:
total dose = $4.36E+15(\text{cm}^{-3})$ standard D = $9.85E-06(\text{cm})$
peak conc = $1.76E+20(\text{cm}^{-3})$ impl range = $1.00E-06(\text{cm})$
ave conc = $8.72E+19(\text{cm}^{-3})$ jct depth = $5.00E-05(\text{cm})$*

where ave is the abbreviation of average, impl of implantation, D of deviation, jct of junction and conc of concentration.

6. Lateral Diffusion

After the doping profile is defined, the effect of lateral diffusion is displayed as:

*Drawn source/drain junctions at (0.000um, 2.340um).....(4, 42)
Corrected by side diffusions as (.400um, 1.940um).....(15, 31)
Lateral diffusion length of s/d:(.400um, .400um)
Effective channel length: 1.541um*

7. Check Mesh and Profile, Save Parameters

After the setup, the mesh and the doping profile can be examined by answering Yes to the requests.

REQUEST->

Check impurity profile (Yes=f7/No=f8) ?
Check the mesh (Yes=f7/No=f8) ?

The other related information will be requested as explained in Section 9. The input parameters entered from the keyboard can be saved on the disc for repeated use by answering Yes to the request and specifying the file name to be used.

REQUEST->

Save input parameters (Yes=f7/No=f8) ?
Data file name ?

8. Potential Initialization and Self-Consistent Solution

REQUEST->

Applied voltages: VD, VG, VS, VB ?
Absolute resolution of 1-D iteration (mVs) ?
Absolute resolution of 2-D solution (mVs) ?
Relaxation factor ($1 \leq x < 2$, ~1.7) ?
Maximum count of 2-D iterations ?
Convergence information per 2-D iteration (Yes=f7/No=f8) ?
Search for specific surface potential (Yes=f7/No=f8) ?

The suggested resolution of initialization is approximately from 0.2 to 0.01 mV. The relaxation factor should be equal to or greater than one, but less than and not equal to 2. Numbers close to 1.7 have been proved adequate. The optimal value varies depending upon the structure and the bias. If searching a specific surface potential is desired, the following question will be asked:

REQUEST->

*Target surface potential value ?
Iterate which bias ($D=V_d, G=V_g, S=V_s, B=V_b$) ?
Searching tolerance (mVs) ?*

A summary of the initialization is displayed. For example:

*Initialize column 1: Converged at 26th iteration, maximum deviation = 0.00
Initialize column 19: Converged at 50th iteration, maximum deviation = .190E-03
Initialize column 50: Converged at 50th iteration, maximum deviation = .827E-04
Equal potential region between -.05um(2) and .09um(11) as -.10um(1)
Equal potential region between .91um(35) and 1.24um(49) as 1.30um(50)
Lateral depletion layer between .30um(19) and .91um(35)
Lateral depletion layer between .09um(11) and .61um(25)*

The two-dimensional iteration either converges or is limited by the given count. The convergence message of each iteration loop can be turned on or off as desired. The message assumes the following format:

10th loop: max deviation = 2.866E-02, at (35,12), by-pass 42.79%

A summary is displayed at the end of the two-dimensional iteration:

*2-D iteration stops at loop 85:
last max deviation = 2.158E-04, at (44,18),
by pass 55.80% ave per loop
At surface
Potential minimum = .199 at $X = .920\text{um}$, (23)
Barrier height = .683
Current density = 1.245E-08 Amp/cm²
Barrier width = .654um,
from .554um to 1.208um...(19,26)
Source depletion width = .133um
Drain depletion width = .210um
Saddle potential = .200, barrier height = -.682
at (.920um, .130um)...(23, 6)
current density = 2.014E-08 Amp/cm²
Barrier width = .404um,
from .718um to 1.122um...(21,25)*

The result can be checked at this point by answering Yes to the following request.

REQUEST->

Check results (Yes=f7/No=f8) ?

The procedure is explained in the next section.

9. Output

The results may be displayed and examined at each check point, i.e. after the setup and 2-D iteration steps.

REQUEST->

*Which one? 2-dimensional plots/f1, 3-dimensional plots/f2,
save in Fmgr file/f3, print the numbers/f4*

After the choice is made, the domain of display will be requested. For a 2-D display, the user has to select an X or Y cross section and define the domain.

REQUEST->

*Constant X or Y ?
Cross section index ?
From <> to <> (indices) ?*

The functional values in the defined domain will be displayed to help the user estimate the minimum and the maximum. For the other choices of display, the messages are:

REQUEST->

*From <> to <> (X-direction) ?
From <> to <> (Y-direction) ?*

At this point, a 7x8 table is displayed to help the user determine the appropriate minimum and maximum. Then the following question is prompted:

REQUEST->

Estimated MIN/MAX function values (MIN=>MAX->skip) ?

If MIN is greater than or equal to MAX, the output will be skipped.

9.1. 3-D Graphics Display (f2)

REQUEST->

*On the console (Yes=f7/No=f8) ?
 Log scale (Yes=f7/No=f8) ?
 How many points in X-direction ?
 How many points in Y-direction ?
 Tilt angle (degree) ?
 Rotation angle (degree) ?*

After the results have been plotted on the screen, graphs may be re-drawn on the plotter.

9.2. Numerical Display (f3,f4)

The results may be routed to the printer or saved on the disc.

9.3. More Outputs

Other data may be obtained at each check point. The user may have more than one output. The output alternatives are determined by the answer to the following request.

REQUEST->

*Which one? doping concentration/f1, free carrier profile/f2,
 field distribution/f3, potential profile/f4.*

Except for the choice of displaying doping profile, the signs of the results will be changed if the answer to the following question is Yes.

REQUEST->

Referring to electron (Yes=f7/No=f8) ?

There are four field-display options.

REQUEST->

*Which one? X-component(f1), Y-component(f2),
X/Y-ratio(f3) or magnitude(f4).*

10. Loops

The simulation can be repeated at a different bias without re-defining the geometry and the profile. The user can also analyze a new structure using a profile defined by the same process parameters or analyze the old structure using different process parameters.

REQUEST->

*Another bias (Yes=f7/No=f8) ?
Another run (Yes=f7/No=f8) ?
Redefine the structure (Yes=f7/No=f8) ?
Redefine the profile (Yes=f7/No=f8) ?*

11. Open File Error

If the specified disc file cannot be opened, the user can try again or exit.

12. Input File Format

12.1. Case of Analytically Generated Profile

- line.1: title line
- line.2: drawn channel length (μm)
- line.3: lateral span of source (μm)
- line.4: lateral span of drain (μm)
- line.5: oxide thickness: thin? and thick ? (μm)
- line.6: thin-oxide location: from ? to ? (μm)
- line.7: lateral span of oxide ramp (μm)
- line.8: drawn gate location: from ? to ? (μm)
- line.9: depth of the simulated structure? (μm)
- line.10: substrate dopant: B, As, Ph, Sb, +(n-type), -(p-type)
- line.11: substrate doping concentration (*1E15 cm⁻³)
- line.12: well implant dopant: B, As, Ph, Sb, +, -
- line.13: well implant range(μm), stndev(μm) and dose (cm⁻²)
- line.14: diffusion constant of well implant (cm²/sec)
- line.15: drive in temperature for well implant ($^{\circ}C$)
- line.16: drive in time for well implant (min)
- line.17: localized implant location: from ? to ? (μm)
- line.18: local implant dopant: B, As, Ph, Sb, +, -
- line.19: local implant range(μm), stndev(μm) and dose (cm⁻²)
- line.20: diffusion constant of selective implant (cm²/sec)
- line.21: drive in temperature for selective implant ($^{\circ}C$)

- line.22: drive in time for selective implant (min)
- line.23: source/drain implant dopant: B, As, Ph, Sb, +, -
- line.24: src/drn implant range(μm), stndev(μm) and dose (cm-2)
- line.25: diffusion constant of src/drn implant (cm²/sec)
- line.26: drive in temperature for src/drn implant ($^{\circ}C$)
- line.27: drive in time for src/drn implant (min)"

12.2. Case of SUPREM generated profile

- line.1: title line
- line.2: drawn channel length (μm)
- line.3: lateral span of source (μm)
- line.4: lateral span of drain (μm)
- line.5: oxide thickness: thin? and thick ? (μm)
- line.6: thin oxide location: from ? to ? (μm)
- line.7: lateral span of oxide ramp (μm)
- line.8: drawn gate location: from ? to ? (μm)
- line.9: depth of the simulated structure? (μm)
- line.10: index of SUPREM input F
- line.11: substrate dopant: B, As, Ph, Sb, +(n-type), -(p-type),
- line.12: index of non-uniform substrate N
- line.12.a: if line 12 is not N in 1st column:
substrate doping concentration (*1E15 cm-3)
- line.12.b: well implant dopant: B, As, Ph, Sb, +, -
- line.13: standard deviation(μm) of well implant
- line.14: SUPREM save file name of well implant

- line.15: column index of well implant
- line.16: localized implant location: from ? to ? (μm)
- line.17: local implant dopant: B, As, Ph, Sb, +, -
- line.18: local implant standard deviation(μm)
- line.19: local implant file name
- line.20: local implant column index
- line.21: source/drain implant dopant: B, As, Ph, Sb, +, -
- line.22: src/drn implant standard deviation(μm)
- line.23: src/drn implant file name
- line.24: src/drn implant column index

APPENDIX B

Example Input to Program TWIST

1. Input to TWIST

```
***** TWIST *****
1.84          ..drawn channel length ( $\mu m$ )
0.184        ..lateral span of source ( $\mu m$ )
0.368        ..lateral span of drain ( $\mu m$ )
6.50E-02  0.60  ..oxide thickness: thin? and thick ? ( $\mu m$ )
0.0    1.84    ..thin oxide location: from ? to ? ( $\mu m$ )
0  .0         ..lateral span of oxide ramp ( $\mu m$ )
0.0    1.84    ..drawn gate location: from ? to ? ( $\mu m$ )
4.5          ..depth of the simulated structure? ( $\mu m$ )
F            ..SUPREM input index
B            ..subs dopant: B,As,Ph,Sb, +, -
U            ..index of non-uniform substrate N
0.75        ..substrate concentration ( $*10^{15} cm^{-3}$ )
$           ..well implant dopant
0           ..standard deviation( $\mu m$ ) of well implant
xxxxx1::s3  ..SUPREM save file name of well implant
1           ..column index of well implant
9 -9       ..localized implant location: from/to( $\mu m$ )
$           ..local implant dopant: B, As, Ph, Sb, +, -
0           ..local implant standard deviation( $\mu m$ )
0           ..local implant file name
0           ..local implant column index
```

```

As                ..src/drn implant dopant: B,As,Ph,Sb,+,-
0.02             ..src/drn implant standard deviation( $\mu m$ )
suprm2::s3       ..src/drn implant file name
2               ..src/drn implant column index

```

2. Input to SUPREM for Generating Example Profile

```

title 2706 enhancement, check source/drain junction
global lev1=2
subs ornt=100, elem=b, conc=7.5e14
grid dysi=0.01, dpth=0.75, ymax=1.0
print head=n, idiv=n, totl=n
plot idiv=n, totl=n
step type=oxid, time=30, temp=850, trte=10, modl=nit0
step type=oxid, time=4, temp=1150, modl=dry5
step type=oxid, time=70, temp=1150, trte=-4.286, modl=nit0
step type=impl, elem=b, dose=4e11, akev=100
print head=y, idiv=n, totl=n
plot wind=0.8, cmin=14, ndec=8, totl=n, idiv=y
step type=impl, elem=as, dose=1e16, akev=100
step type=oxid, time=25, temp=900, modl=nit0
print head=y, idiv=y, totl=n
step type=oxid, time=75, temp=1000, modl=nit0
model name=dry5, lrte=2.5e5, lrea=2.0, prte=52.0, prea=1.23
save lunm=20, type=ascii
end

```


APPENDIX C

Example Console Session of Program TWIST

Input from the console (Yes=f7/No=f8)? "No"

Input data file name? "@input::xx"

***** Input Summary *****

drawn channel length 1.84um

lateral span of source .18um

lateral span of drain .37um

oxide thickness: thin: .06um, thick: .60um

thin oxide loc: from 0.00um to 1.84um

lateral oxide ramp 0.00um

drawn gate loc: from 0.00um to 1.84um

depth of the structure 4.50um

Use SUPREM generated profile.

Uniform substrate of dopant: B, concentration = $-7.500E+14\text{cm}^{-3}$

.... profile parameters:

total dose = $4.36E+15(\text{cm}^{-3})$ standard D = $9.85E-06(\text{cm})$

peak conc = $1.76E+20(\text{cm}^{-3})$ impl range = $1.00E-06(\text{cm})$

ave conc = $8.72E+19(\text{cm}^{-3})$ jct depth = $5.00E-05(\text{cm})$

Drawn source/drain junctions at (0.00um, 1.84um).....(4, 42)

Corrected by side diffusions as (.42um, 1.42um).....(17, 29)

Lateral diffusion length of s/d:(.42um, .42um)

Effective channel length: 1.00um

Check impurity profile? (Yes=f7/No=f8) "No"

Check the mesh? (Yes=f7/No=f8) "No"

Save input parameters? (Yes=f7/No=f8) "No"

User's responses are in quotes.

Applied voltages: Vd, Vg, Vs, Vb ? "1.3 0 0"
 Absolute resolution of 1-D iteration (mVs) ? ".1"
 Absolute resolution of 2-D solution (mVs) ? ".5"
 Relaxation factor ($1 < x < 2$, "1.7" ? "1.7"
 Maximum count of 2-D iterations ? "300"
 Convergence information per 2-D iteration (Yes=f7/No=f8) ? "No"
 Search for specific surface potential (Yes=f7/No=f8) ? "No"
 Initialize column 1: Converged at 17th iteration, maximum deviation = 0.00
 Initialize column 18: Converged at 12th iteration, maximum deviation = 0.00
 Initialize column 49: Converged at 28th iteration, maximum deviation = 0.00
 Equal potential region between -12um(2) and .37um(16) as -.18um(1)
 Equal potential region between 1.47um(30) and 2.14um(48) as 2.21um(49)
 Lateral depletion layer between .48um(18) and 1.47um(30)
 Lateral depletion layer between .37um(16) and 1.36um(28)
 ***** End of Initialization *****

**2-D iteration stops at loop 81:
 last max deviation = 9.803E-04, at (24,17), by pass 62.25% ave per loop
 At surface
 Potential minimum = .551, at X = .632, (20)
 Barrier height = .331
 Current density = 2.077E-08 Amp/cm²
 Barrier width = .392um, from .422 to .814...(17,22)
 Barrier depth = .859um, from 0.000 to .859...(1,22)
 Current / width = 8.27 Amp/um, with U_{so}=700.0 cm²/sec-V
 Source depletion width = 0.000um
 Drain depletion width = .605um
 Check results (Yes=f7/No=f8) ? "No"
 More iterations (Yes=f7/No=f8) ? "No"

***** End of Two Dimensional Solution *****

Another bias point (Yes=f7/No=f8) ? "Yes"
 Applied voltages: Vd, Vg, Vs, Vb ? "2 .3 0 0"
 Re-initialize the potential (Yes=f7/No=f8) ? "Yes"
 With same iteration parameters (Yes=f7/No=f6) ? "Yes"
 Search for specific surface potential (Yes=f7/No=f8) ? "No"
 Initialize column 1:Converged at 17th iteration, maximum deviation = 0.00
 Initialize column 18:Converged at 12th iteration, maximum deviation = 0.00
 Initialize column 49:Converged at 35th iteration, maximum deviation = 0.00
 Equal potential region between -.12um(2) and .37um(16) as -.18um(1)
 Equal potential region between 1.47um(30) and 2.14um(48) as 2.21um(49)
 Lateral depletion layer between .48um(18) and 1.47um(30)
 Lateral depletion layer between .37um(16) and 1.36um(28)
 ***** End of Initialization *****
 **2-D iteration stops at loop 111:
 last max deviation =1.049E-03, at (29,15), by pass 63.23% ave per loop
 At surface
 Potential minimum = .589, at x = .484, (18)
 Barrier height = .293
 Current density = 4.167E-08 Amp/cm2
 Barrier width = .210um, from .422 to .632...(17,20)
 Barrier depth = 1.000um, from 0.000 to 1.000...(1,24)
 Current / width = 94.2 Amp/um, with $U_{so}=700.0 \text{ cm}^2/\text{sec-V}$
 Source depletion width = 0.000um
 Drain depletion width = .787um
 Saddle potential = .589, barrier height= -.293 at (.484, .023)...(18, 2)
 Injection current /width = 87.4 Amp/um, with $U_{so}=700.0 \text{ cm}^2/\text{sec-V}$
 Check results (Yes=f7/No=f8) ? "Yes"
 Which one ? (2-dimensional plots/f1), (3-dimensional plots/f2),
 (Save in Fmgr file /f3), (Print the numbers /f4). "Save on disc"

Referring to electron? (Yes=f7/No=f8) "No"

X-mesh->(n,x): "1 50"

Y-mesh->(n,y): "1 50"

-	1	2	3	4	5	6	7
YX(um)	-.18	-.12	-5.50E-02	0.0	1.60E-02	3.37E-02	5.34E-02
1 0.00	.88	.88	.87	.87	.86	.86	.85
2 .02	.88	.88	.87	.86	.86	.86	.85
3 .05	.88	.88	.87	.86	.86	.86	.85
4 .07	.88	.88	.87	.86	.86	.85	.85
5 .10	.88	.88	.87	.86	.86	.85	.85
6 .13	.88	.87	.87	.86	.86	.85	.85
7 .16	.87	.87	.87	.86	.85	.85	.84
8 .19	.87	.87	.86	.85	.85	.84	.84

Estimated MIN/MAX function values? (MIN=>MAX->skip) "0 1"

File name? "@poten::xx"

Another output? (Yes=f7/No=f8) "Yes"

Which one ? (Doping concentration/f1), (Carrier distribution/f2),

(Field distribution /f3), (Potential profile /f4). "Carrier"

Which one ? (2-dimensional plots/f1), (3-dimensional plots/f2),

(Save in FMGR file /f3), (Print the numbers /f4). "Save on disc"

Referring to electron? (Yes=f7/No=f8) "No"

X-mesh->(n,x): "1 50"

Y-mesh->(n,y): "1 50"

-	1	2	3	4	5	6	7
YX(um)	-.18	-.12	-5.50E-02	0.0	1.60E-02	3.37E-02	5.34E-02
1 0.00	-1.7E+20	-1.5E+20	-1.2E+20	-8.9E+19	-7.5E+19	-6.5E+19	-5.2E+19
2 .02	-1.7E+20	-1.5E+20	-1.2E+20	-8.9E+19	-7.4E+19	-6.4E+19	-5.1E+19
3 .05	-1.6E+20	-1.5E+20	-1.2E+20	-8.7E+19	-7.3E+19	-6.3E+19	-5.0E+19
4 .07	-1.6E+20	-1.4E+20	-1.1E+20	-8.3E+19	-7.0E+19	-6.0E+19	-4.8E+19
5 .10	-1.5E+20	-1.3E+20	-1.0E+20	-7.8E+19	-6.6E+19	-5.7E+19	-4.5E+19
6 .13	-1.3E+20	-1.2E+20	-1.0E+20	-7.2E+19	-6.1E+19	-5.2E+19	-4.2E+19
7 .16	-1.2E+20	-1.1E+20	-9.0E+19	-6.5E+19	-5.4E+19	-4.7E+19	-3.8E+19
8 .19	-1.0E+20	-9.7E+19	-7.8E+19	-5.6E+19	-4.7E+19	-4.1E+19	-3.3E+19

Estimated MIN/MAX function values? (MIN=>MAX->skip) "0 1"

File name? "@carri::xx"

Another output? (Yes=f7/No=f8) "No"

More iterations (Yes=f7/No=f8) ? "No"

***** End of Two Dimensional Solution *****

Another bias point (Yes=f7/No=f8) ? "No"

Another run (Yes=f7/No=f8) ? "No"

APPENDIX D

Test-Circuit Inputs to SPICE2.G

Invchn - Five-Stage Saturated Inverter Chain by Short MOS (MOS3)

```
.tran 0.12n 12n
.options defad=1e-9 defas=1e-9
.opt acct
.op
m1 7 7 2 8 nmos w=5u l=2.3u
m2 2 1 0 8 nmos w=50u l=2.3u
m3 7 7 3 8 nmos w=5u l=2.3u
m4 3 2 0 8 nmos w=50u l=2.3u
m5 7 7 4 8 nmos w=5u l=2.3u
m6 4 3 0 8 nmos w=50u l=2.3u
m7 7 7 5 8 nmos w=5u l=2.3u
m8 5 4 0 8 nmos w=50u l=2.3u
m9 7 7 6 8 nmos w=5u l=2.3u
ma 6 5 0 8 nmos w=50u l=2.3u
vin 1 0 pulse(5 0 0.2n 1n 1n 5n 12n)
vdd 7 0 dc 5
vbb 8 0 dc 0
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+ uo=580 theta=0.06 vmax=20e4 level=3 kappa=1.0 eta=0.035)
.plot tran v(2) v(3) v(4) v(5) v(6) v(1) (-1,5)
.print tran v(2) v(3) v(4) v(5) v(6) v(1)
.end
```

Ratlog - Ratioless Dynamic Logic Circuit by Short MOS(MOS3)

```
.opt acct defl=2.3u defw=50u defas=1n defad=1n
.tran 1n 110n
m1 9 11 2 10 nmos
m2 9 12 4 10 nmos
m3 2 1 0 10 nmos
m4 4 3 0 10 nmos
m5 3 12 2 10 nmos
m6 1 11 5 10 nmos
c1 1 0 0.05pf
c2 2 0 0.05pf
c3 3 0 0.05pf
c4 4 0 0.05pf
c5 5 0 0.05pf
vin 5 0 pulse(0 4 1n 2n 2n 20n 500n)
vp1 11 0 pulse(0 5 1n 2n 2n 12n 52n)
vp2 12 0 pulse(0 5 26n 2n 2n 12n 52n)
vdd 9 0 dc 5
vbb 10 0 dc -2.5
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+   uo=580 theta=0.06 vmax=20e4 level=3 kappa=1.0 eta=0.035)
.plot tran v(4) v(1) v(2) v(3) v(4) v(11) v(12) (0,6)
.print tran v(4) v(1) v(2) v(3) v(4) v(11) v(12) (0,6)
.end
```

Mosmem - MOS Memory Cell by Short MOS (MOS3)

```
.opt acct defas=2n defad=2n defl=2.3u
.tran 0.5ns 60ns
.op
vdd 9 0 dc 5
vs 7 0 pulse(2 0 30ns 2ns 2ns 30ns 200ns)
vw 1 0 pulse(0 2 1ns 2ns 40ns 10ns 200ns)
vwb 2 0 pulse(2 0 1ns 2ns 2ns 100ns 200ns)
m1 3 1 0 0 nmos w=50u
m2 4 2 0 0 nmos w=50u
m3 9 9 3 0 nmos w=5u
m4 9 9 4 0 nmos w=5u
m5 5 7 3 0 nmos w=5u
m6 6 7 4 0 nmos w=5u
m7 5 6 0 0 nmos w=50u
m8 6 5 0 0 nmos w=50u
m9 9 9 5 0 nmos w=5u
m10 9 9 6 0 nmos w=5u
m11 8 4 0 0 nmos w=50u
m12 9 9 8 0 nmos w=5u
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+ uo=580 theta=0.06 vmax=20e4 level=3 kappa=1.0 eta=0.035)
.print tran v(6) v(5) v(7) v(1) v(2) v(8)
.plot tran v(6) v(5) v(7) v(1) v(2) v(8) (0,5)
.end
```


Bootinv - Bootstrapped Double Inverter Circuit by Short MOS (MOS3)

```
.opt acct
.tran 0.2ns 20ns
.op
m1 1 1 3 6 nmos w=10u l=2.3u ad=0.02p as=0.02p
m2 3 2 0 6 nmos w=50u l=2.3u ad=2p as=0.02p
m3 1 1 4 6 nmos w=10u l=2.3u ad=0.2p as=0.2p
m4 1 4 5 6 nmos w=10u l=2.3u ad=0.02p as=0.02p
m5 5 3 0 6 nmos w=50u l=2.3u ad=2p as=0.02p
cl5 5 0 0.1pf
cl2 3 0 0.1pf
cb4 4 5 0.1pf
vdd 1 0 dc 5
vbb 6 0 dc 0
vin 2 0 pulse(4 0 1ns 2ns 2ns 13ns 20ns)
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+ uo=580 theta=0.06 vmax=20e4 level=3 kappa=1.0 eta=0.035)
.print tran v(5) v(3) v(4) v(2)
.plot tran v(5) v(3) v(2) (0,5)
.plot tran v(4)
.end
```

Invchn - Five-Stage Saturated Inverter Chain by Short MOS (MOS2)

```
.tran 0.12n 12n
.options defad=1e-9 defas=1e-9
.opt acct
.op
m1 7 7 2 8 nmos w=5u l=2.3u
m2 2 1 0 8 nmos w=50u l=2.3u
m3 7 7 3 8 nmos w=5u l=2.3u
m4 3 2 0 8 nmos w=50u l=2.3u
m5 7 7 4 8 nmos w=5u l=2.3u
m6 4 3 0 8 nmos w=50u l=2.3u
m7 7 7 5 8 nmos w=5u l=2.3u
m8 5 4 0 8 nmos w=50u l=2.3u
m9 7 7 6 8 nmos w=5u l=2.3u
ma 6 5 0 8 nmos w=50u l=2.3u
vin 1 0 pulse(5 0 0.2n 1n 1n 5n 12n)
vdd 7 0 dc 5
vbb 8 0 dc 0
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+   uo=450 ucrit=12e4 uexp=0.240 utra=0.25 level=2
+   vmax=6e4 neff=7)
.plot tran v(2) v(3) v(4) v(5) v(6) v(1) (-1,5)
.print tran v(2) v(3) v(4) v(5) v(6) v(1)
.end
```

Ratlog - Ratioless Dynamic Logic Circuit by Short MOS(MOS2)

```
.opt acct defl=2.3u defw=50u defas=1n defad=1n
.tran 1n 110n
m1 9 11 2 10 nmos
m2 9 12 4 10 nmos
m3 2 1 0 10 nmos
m4 4 3 0 10 nmos
m5 3 12 2 10 nmos
m6 1 11 5 10 nmos
c1 1 0 0.05pf
c2 2 0 0.05pf
c3 3 0 0.05pf
c4 4 0 0.05pf
c5 5 0 0.05pf
vin 5 0 pulse(0 4 1n 2n 2n 20n 500n)
vp1 11 0 pulse(0 5 1n 2n 2n 12n 52n)
vp2 12 0 pulse(0 5 26n 2n 2n 12n 52n)
vdd 9 0 dc 5
vbb 10 0 dc -2.5
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+ uo=450 ucrit=12e4 uexp=0.240 utra=0.25 level=2
+ vmax=6e4 neff=7)
.plot tran v(4) v(1) v(2) v(3) v(4) v(11) v(12) (0,6)
.print tran v(4) v(1) v(2) v(3) v(4) v(11) v(12) (0,6)
.end
```

Mosmem - MOS Memory Cell (MOS2)

```
.opt acct defas=2n defad=2n defl=2.3u
.tran 0.5ns 60ns
.op
vdd 9 0 dc 5
vs 7 0 pulse(2 0 30ns 2ns 2ns 30ns 200ns)
vw 1 0 pulse(0 2 1ns 2ns 40ns 10ns 200ns)
vwb 2 0 pulse(2 0 1ns 2ns 2ns 100ns 200ns)
m1 3 1 0 0 nmos w=50u
m2 4 2 0 0 nmos w=50u
m3 9 9 3 0 nmos w=5u
m4 9 9 4 0 nmos w=5u
m5 5 7 3 0 nmos w=5u
m6 6 7 4 0 nmos w=5u
m7 5 6 0 0 nmos w=50u
m8 6 5 0 0 nmos w=50u
m9 9 9 5 0 nmos w=5u
m10 9 9 6 0 nmos w=5u
m11 8 4 0 0 nmos w=50u
m12 9 9 8 0 nmos w=5u
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+ uo=450 ucrit=12e4 uexp=0.240 utra=0.25 level=2
+ vmax=6e4 neff=7)
.print tran v(6) v(5) v(7) v(1) v(2) v(8)
.plot tran v(6) v(5) v(7) v(1) v(2) v(8) (0,5)
.end
```

Bootinv - Bootstrapped Double Inverter Circuit by Short MOS (MOS2)

```
.opt acct
.tran 0.2ns 20ns
.op
m1 1 1 3 6 nmos w=10u l=2.3u ad=0.02p as=0.02p
m2 3 2 0 6 nmos w=50u l=2.3u ad=2p as=0.02p
m3 1 1 4 6 nmos w=10u l=2.3u ad=0.2p as=0.2p
m4 1 4 5 6 nmos w=10u l=2.3u ad=0.02p as=0.02p
m5 5 3 0 6 nmos w=50u l=2.3u ad=2p as=0.02p
cl5 5 0 0.1pf
cl2 3 0 0.1pf
cb4 4 5 0.1pf
vdd 1 0 dc 5
vbb 6 0 dc 0
vin 2 0 pulse(4 0 1ns 2ns 2ns 13ns 20ns)
.model nmos nmos(vto=0.452 nsub=3.6e15 tox=0.065u ld=0.35u xj=0.5u
+   uo=450 ucrit=12e4 uexp=0.240 utra=0.25 level=2
+   vmax=6e4 neff=7)
.print tran v(5) v(3) v(4) v(2)
.plot tran v(5) v(3) v(2) (0,5)
.plot tran v(4)
.end
```

APPENDIX E

Listing of Program TWIST

File: TUDEFM

*DEFINE HP1000
*DEFINE INTERACTIVE
*DEFINE HP2648A
*DEFINE GRAPHICS
RAT4
S/(EXP)/E/G

File: TCOMNH

COMMON /CTRL/ KONSOL,KLOOP,KSUPR,KREAD,INPFIL(10),KEYBRD,^
NEWNSH,NEWDDP,KOBUG,LURD1,LURD2,LURR
COMMON /GEOM/ KCHANL,KSORC,KDRAIN,KCATEO,KCATE1,TOXO,TOX1,^
KXO,KXI,KXR,KIMPLO,KINPLI,^
KXZ, YRZ
COMMON /INPLT/ TYPE,CSUB,DOPE(3),RANGE(3),STNDV(3),DOSE(3),^
TEMP(3),DCOEF(3),DRVIN(3),KJCT(3),CPEAK(3),CSTEP(3)
COMMON /INDEX/ NSOURC,KDRAIN,KCATEO,KCATE1,KXO,KXI,KIMPLO,KINPLI,^
KXMAX,KYMAX,KOXIDE,^
NSRCO,NDRMO
COMMON /PARAM/ USURF(3),CSURF(3),^
VFB,PHIB,GAMM,ALPHA,PHIJ,CHINRO,^
STYPE(3),PHIF(3),VBCAT(3),GANN(3),ALPHA(3),PHIMP(3)
COMMON /POTEN/ VDB,VGB,VSB,PHIF,PHIFM,ATOL1,ATOL2,RELAX1,RELAX2,^
KIMSGO,KIMSG1,KIMSG2,LOCPHF(2,40),COPPHF(2,40),^
KMAX2,KPHIS,KBIAS,PHSREF,ATOLB,VB
COMMON /CONST/ Q,EPBI,EPSTO2,VT300K,CNI

File: TENA

```
COMMON /XYZ/ Z(50,50),CQNC(50,40),CARRIE(50,40),POTSI(50,48),^  
XPOS(50),YPOS(40),DELX(49),DELY(47),QONE(50,48),^  
CNORTH(50,48),CSOUTH(50,40),CEAST(50,40),CWEST(50,40),^  
CNOX(50,2),CSOX(50,2),CEOX(50,2),CWOX(50,2),^  
QONE1(47),CN1(47),CS1(47),QONES1(50),CNS1(50),CSS1(50),^  
POTOX(50,2),DELOX(50,2),CNOX1(50,2),CSOX1(50,2)
```

File: TCOMHO

```
*CALL TCOMHN  
COMMON /TOUTV/ X1,X2,Y1,Y2,Z1,Z2,TILT,ROTAT,MX1,MX2,MY1,MY2,^  
MX,MY,LU,KLOG  
COMMON /GLABL/ LABLK(40),LABLY(40),LABLZ(40),KFONTX(2,10),KFONTY(2,10),^  
KFONTZ(2,10)
```



```

*CALL TDEFN
*IF HP1000
ENACXYZ.0)
*ENDIF
*IF HP1000&IBATCH
PROGRAM TWIST
*ENDIF
*IF HP1000&BATCH
PROGRAM TWISB
*ENDIF
*IF IHP1000
PROGRAM TWIST (INPUT=201,OUTPUT=201,SUPSAV=201,KONSOL=201,KEYBRD=201,^
TAPES=INPUT,TAPE6=OUTPUT,TAPE7=SUPSAV,TAPE8=KONSOL,^
TAPES=KEYBRD)
*ENDIF
      Two-dimensional Interactive Simulation of MOS Transistors
      Sally Liu
      Bernd Hoeflinger
      Donald G. Pederson      March 1980
*CALL TEMA
*CALL TCONM0
*IF IHP1000
DATA      0/1.692<EXP>-19/, EPS1/1.036<EXP>-12/,EPS102/3.45<EXP>-13/,^
VT300K/0.0259<EXP>0/, CNI/1.450<EXP>+10/
*ENDIF
DATA KYES/2HY /
      ASSIGN LU UNIT NUMBERS
*IF HP1000&IBATCH
KONSOL=ITRLU(JUNK)
KEYBRD=KONSOL
*ENDIF
*IF HP1000&BATCH
CALL SYSIO
KONSOL=6
KEYBRD=3
*ENDIF
*IF IHP1000
KONSOL=9
KEYBRD=0
LURD1=5
LURD2=7
LUR=6
*ENDIF
      PREPARE THE TERMINAL: NONE CURSOR
      CLEAR SCREEN
      DISPLAY LOGO
      DEFINE SOFT KEYS: F7=YES AND F8=NO
      LOCK DISPLAY MEMORY
*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-1)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-1)
*ENDIF
      INITIALIZE GEOMETRY AND DOPING PROFILE
KGO=1
KLOOP=0
      WHILE (KGO.EQ.1) I
      KLOOP=KLOOP+1
*IF HP1000&IBATCH
CALL LINK (1HA)
CALL LINK (1HB)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1HI)
CALL LINK (1H2)
*ENDIF
*IF IHP1000
CALL GETPA
CALL SETPA
*ENDIF
      CHECK PROFILE

```

```

*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-2)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H4,KANSUR,-2)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-2)
*ENDIF
      IF (KANSUR.EQ.KYES) CALL OUTPS (1)
      CHECK MESH
*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-3)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H4,KANSUR,-3)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-3)
*ENDIF
      IF (KANSUR.EQ.KYES) CALL OUTPS (-1)
      SAVE INPUT PARAMETERS
*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-4)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H4,KANSUR,-4)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-4)
*ENDIF
      IF (KANSUR.EQ.KYES) CALL OUTPS (0)
      SOLVE FOR POTENTIAL
      KSOLV=0
      REPEAT (
*IF HP1000&IBATCH
CALL LINK (1HC,KSOLV)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H3,KSOLV)
*ENDIF
*IF IHP1000
CALL SOLVE (KSOLV)
*ENDIF
      IF (KSOLV.NE.0) CALL OUTPS (4)
      UNTIL (KSOLV.EQ.0)
      CHECK IF ANOTHER RUN
*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-5)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H4,KANSUR,-5)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-5)
*ENDIF
      IF (KANSUR.EQ.KYES) KGO=1
      ELSE KGO=0
      UN-LOCK THE MEMORY
*IF HP1000&IBATCH
CALL LINK (1HD,KANSUR,-6)
*ENDIF
*IF HP1000&BATCH
CALL LINK (1H4,KANSUR,-6)
*ENDIF
*IF IHP1000
CALL OUTP1 (KANSUR,-6)
*ENDIF
*IF HP1000&IBATCH
CALL EXEC (6)
*ELSE
STOP
*ENDIF
END

```

File: ATWIST

```
*IF HP1000
  BLOCK DATA TBLKD, Common Blocks
  0
  0   INITIALIZE COMMON BLOCKS
  0
  0
  0 *CALL TCONNO
  0
  DATA   Q/1.692<EXP>-19/, EPS1/1.036<EXP>-12/,EPS102/3.45<EXP>-13/,^
          VT300K/0.0259<EXP>0/,  CNI/1.450<EXP>+10/
  0
  0   END
  0 *ELSE
  0   INTEGER FUNCTION IFBK (DUMMY)
  0   IFBK=0
  0   RETURN
  0   END
  0 *ENDIF
```

File: ANGLE

```
*CALL TDEFN
  SUBROUTINE ANGLE (THETA,KQUAD) -
  0
  0   1) CHANGE ANGLE THETA FROM DEGREE TO RADIENT
  0   2) LIMIT IT BETWEEN 0 AND 2-PI
  0   3) SET QUADRANT-INDEX KQUAD
  0
  0
  0   ..... DEFINE CONSTANTS
  0   PI=4.0<EXP>0*ATAN2(1.0<EXP>0,1.0<EXP>0)
  0   TWOPI=PI*PI
  0   RAD=PI/180.0<EXP>0
  0   QUAD12=0.5<EXP>0*PI
  0   QUAD23=PI
  0   QUAD34=PI+QUAD12
  0   QUAD41=0.0<EXP>0
  0
  0   ..... TRANSFORM THETA FROM DEGREE INTO RADIENT, TAKE THE ABSOLUTE VALUE
  0   THETA=THETA*RAD
  0   ABSX=ABS(THETA)
  0
  0   ..... LIMIT THETA BETWEEN 0 AND 2-PI
  0   WHILE (ABSX.GT.TWOPI) ABSX=ABSX-TWOPI
  0   IF (THETA.GE.0.0<EXP>0) THETA=ABSX
  0   ELSE THETA=TWOPI-ABSX
  0
  0   ..... GET THE QUADRANT INDEX
  0   IF (THETA.LT.QUAD12) KQUAD=1
  0   ELSE IF (THETA.LT.QUAD23) KQUAD=2
  0   ELSE IF (THETA.LT.QUAD34) KQUAD=3
  0   ELSE KQUAD=4
  0
  0   ..... DONE
  0   RETURN
  0   END
```

File: BASCAL

```
*CALL TUDFNM
SUBROUTINE BASCAL (IGCB,XONY,XMIN,XMAX,YMIN,YMAX)
*
* ALLOCATE AND SCALE THE CENTRAL PORTION OF THE PLOTTING SURFACE
*
* DIMENSION IGCB(192)
*
* ..... DEFINE MARGINS, CASE OF VERTICAL ORIENTATION
* IF (XONY.LE.1.0*(EXP)0) [
*   XFRAME=100.0*(EXP)0
*   YFRAME=XFRAME/XONY
*   XLEFT=XFRAME/3.6*(EXP)0
*   XRITE=XFRAME/6.0*(EXP)0
*   YLOWR=YFRAME*0.2*(EXP)0
*   YUPPR=YLOWR
* ]
* ..... CASE OF HORIZONTAL ORIENTATION
* ELSE [
*   YFRAME=100.0*(EXP)0
*   XFRAME=YFRAME*XONY
*   XLEFT=XFRAME*0.2*(EXP)0
*   XRITE=XLEFT
*   YLOWR=YFRAME/3.6*(EXP)0
*   YUPPR=YFRAME/6.0*(EXP)0
* ]
* ..... DEFINE THE BOUNDARY
* XLIMIT1=XLEFT
* XLIMIT2=XFRAME-XLEFT
* YLIMIT1=YLOWR
* YLIMIT2=YFRAME-YUPPR
* XRATIO=(XMAX-XMIN)/(XLIMIT2-XLIMIT1)
* YRATIO=(YMAX-YMIN)/(YLIMIT2-YLIMIT1)
* ..... DEFINE THE PLOTTING AREA
* CALL VIEWP(IGCB,0.0*(EXP)0,XFRAME,0.0*(EXP)0,YFRAME)
* CALL WINDOW(IGCB,XMIN-XRATIO*XLEFT,XMAX+XRATIO*XRITE,
*             YMIN-YRATIO*YLOWR,YMAX+YRATIO*YUPPR)
* ..... DONE
* RETURN
* END
```

File: BASTEP

```
*CALL TUDFNM
SUBROUTINE BASTEP (KIMPL)
*
* PROCESS PARAMETERS OF STEP PROFILE APPROXIMATION
*
* CALL TCONHN
*
* STNDV2=STNDV(KIMPL)*STNDV(KIMPL)
* FOURDT=(STNDV2+STNDV2)*4.0*(EXP)0+DCOEF(KIMPL)*ORVIN(KIMPL)
* IF (FOURDT.NE.0.0*(EXP)0) [
*   PI=4.0*(EXP)0*ATAN2(1.0*(EXP)0,1.0*(EXP)0)
*   CPEAK(KIMPL)=DOSE(KIMPL)/SQRT(PI*FOURDT)
*   XJCT(KIMPL)=RANGE(KIMPL)*SQRT(FOURDT*ALOG(ABS(CPEAK(KIMPL)/CSUB)))
*   CSTEP(KIMPL)=DOSE(KIMPL)/XJCT(KIMPL)
* ]
* ELSE [
*   CPEAK(KIMPL)=DOSE(KIMPL)
*   XJCT(KIMPL)=RANGE(KIMPL)
*   CSTEP(KIMPL)=DOSE(KIMPL)
* ]
* ..... DISPLAY INPLANT PARAMETERS
* WRITE (KONSOL,1000) DCOEF(KIMPL),CPEAK(KIMPL),XJCT(KIMPL),CSTEP(KIMPL)
1000 FORMAT(/, '... profile parameters: ',
*         /,10X,'diff const =',IPE10.3,'(cm2/sec)',^
*         /,10X,'peak conc =',IPE10.3,'(cm-3)',^
*         /,10X,'jct depth =',IPE10.3,'(cm)',^
*         /,10X,'average conc =',IPE10.3,'(cm-3)')
* ..... DONE
* RETURN
* END
```

```

*CALL TUNDEFN
SUBROUTINE AXLAB (KCCB,KDCB,XONY,X1,X2,Y1,Y2,LABLX,LABLY,KFONTX,KFONTY)
0
0 LABEL AXES ON 2-D PLOTS
0
0 DIMENSION KCCB(1),KDCB(1),LABLK(1),LABLY(1),KFONTX(1),KFONTY(1)
0
0 DATA HDGTO/3/, CHARN/20.0<EXP>0/,<^
ASPEC/0.7<EXP>0/, SLANT/0.0<EXP>0/, SUP/0.75<EXP>0/
0
0 CALL TSCAL (KCCB,XONY,CHARN,CHITE,XLENG,YLENG) 0 SCALE CHARACTER SIZE
CHITY=CNITE*(Y2-Y1)/YLENG 0 X'FORM INTO USER
CHITX=CHITY*(X2-X1)/(Y2-Y1)/XONY 0 DEFINED
CHXFTR=CHITX*SUP 0 UNITS
CHYFTR=CHITY*SUP
CALL LONG (KCCB,1) 0 SET TEXT ORIGIN
CALL LINE (KCCB,0) 0 SET SOLID LINE
PIOM2=2.0<EXP>0*ATAN2(1.0<EXP>0,1.0<EXP>0)
CALL LABLN (KCCB,KDCB,LABLY,KFONTY,CHITE,TEXTX,MFY)
IF (MFY.NE.0) [
CALL LDIR (KCCB,PIOM2) 0 Y-LABEL
0 VERTICAL DIR.
TEXTY=TEXTX*(Y2-Y1)/(X2-X1) 0 SCALE TEXT LENGTH
XO=X1-(HDGTO*0.5<EXP>0)*CHITX
YO=(Y1+Y2-TEXTY)*0.5<EXP>0
CALL MOVE (KCCB,XO,YO) 0 MOVE TO FIRST POINT
XOFF=-CHXFTR 0 DEFINE SUPER-SCRIPT
YOFF=0.0<EXP>0
CALL LABUR (KCCB,KDCB,LABLY,KFONTY,CHITE,MFY,XOFF,YOFF)
]
CALL LABLN (KCCB,KDCB,LABLX,KFONTX,CHITE,TEXTX,MFX)
IF (MFX.NE.0) [
CALL LDIR (KCCB,0.0<EXP>0) 0 X-LABEL
YO=Y1-HDGTO*CHITY*ASPEC-CHITY-CHITY 0 POSITION X-LABEL
XO=(X1+X2-TEXTX)*0.5<EXP>0
CALL MOVE (KCCB,XO,YO) 0 MOVE TO STARTING P'NT
XOFF=0.0<EXP>0
YOFF=CHYFTR
CALL LABUR (KCCB,KDCB,LABLX,KFONTX,CHITE,MFX,XOFF,YOFF)
]
0
0 ..... DONE
RETURN
END

```

```

*CALL TUNDEFN
SUBROUTINE AXLIN (KCCB,KDCB,XONY,X1,X2,Y1,Y2)
0
0 DRAW A FRAME DEFINED BY (X1,X2,Y1,Y2) WITH LINEAR TIC MARK
ALWAYS DIVIDED INTO 5 GRIDS EACH WITH 5 TIC MARKS (TOTALLY 25)
0
0 DIMENSION KCCB(1),KDCB(1),LBUF(4),XTIC(4),YTIC(4),XDEL(4),YDEL(4)
0
0 EQUIVALENCE (NTIC,MXTIC,MYTIC),(NTICO,MXTICO,MYTICO)
0
0 DATA CHARN/25.0<EXP>0/, NSEC/0/, NCR/2HGC/
DATA TRATIO/0.02<EXP>0/,NTICO/25/,HTIC/5/,KGRID/0/
0
0 ..... SCALE THE CHARACTERS
CALL TSCAL (KCCB,XONY,CHARN,CHITE,XLENG,YLENG)
XSPAN=X2-X1; YSPAN=Y2-Y1
CHITY=CHITE*YSPAN/YLENG; CHITX=CHITE*XSPAN/(XONY*YLENG)
0
0 ..... TIC SIZE
TICX=XSPAN*TRATIO; TICX=NTIC(1)-TICX; TICX=NTIC(2)-0.0<EXP>0; TICX=NTIC(3)-TICX; TICX=NTIC(4)-0.0<EXP>0;
TICY=YSPAN*TRATIO; YTIC(1)=0.0<EXP>0; YTIC(2)=TICY; YTIC(3)=0.0<EXP>0; YTIC(4)=-TICY
0
0 ..... THE SPACING
XTSPAC=XSPAN/MXTICO; YTSPAC=YSPAN/MYTICO
XDEL(1)=0.0<EXP>0; YDEL(1)=-YTSPAC
XDEL(2)=XTSPAC; YDEL(2)=0.0<EXP>0
XDEL(3)=0.0<EXP>0; YDEL(3)=YTSPAC
XDEL(4)=-XTSPAC; YDEL(4)=0.0<EXP>0
0
0 ..... LABEL ATTRIBUTION
CALL LONG (KCCB,7)
CALL LINE (KCCB,0)
CALL GFONT (KCCB,6NFONT2 ,NSEC,NCR,KDCB)
NS=1
NC=0
1010 FORMAT (F7.2,1X)
0
0 ..... LEFT, LOWER, RIGHT, UPPER
XP=X1
YP=Y2
PIOM2=2.0<EXP>0*ATAN2(1.0<EXP>0,1.0<EXP>0)
DO KD=1,4 [
XD=XDEL(KD); YD=YDEL(KD) 0 DEFINE SPACE
XT=XTIC(KD); YT=YTIC(KD) 0 DEFINE TIC SIZE
XTO=0.5<EXP>0*XT; YTO=0.5<EXP>0*YT
IF ((KD.EQ.1).OR.(KD.EQ.3)) [
IF (KD.EQ.1) [ CALL LDIR (KCCB,0.0<EXP>0); PRT=YP ]
]
ELSE [
IF (KD.EQ.2) [ CALL LDIR (KCCB,PIOM2); PRT=XP ]
]
CALL MOVE (KCCB,XP,YP)
IF ((KD.EQ.1).OR.(KD.EQ.2)) [
CALL CODE; WRITE (LBUF,1010) PRT 0 MARK 1ST LABEL
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL MOVE (KCCB,XP,YP)
]
DO K=1,NTICO [
XP=XP+XD; YP=YP+YD 0 DRAW THE AXIS
CALL DRAW (KCCB,XP,YP)
KT=MOD(K,NTIC)
IF (KT.EQ.0) [ TX=XT; TY=YT ]
ELSE [ TX=XTO; TY=YTO ]
CALL DRAW (KCCB,XP+TX,YP+TY)
CALL MOVE (KCCB,XP,YP)
IF ((KT.EQ.0).AND.((KD.EQ.1).OR.(KD.EQ.2))) [
IF (KD.EQ.1) PRT=YP
ELSE PRT=XP
CALL CODE; WRITE (LBUF,1010) PRT
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL MOVE (KCCB,XP,YP)
]
]
]
0
0 ..... CLOSE FONT FILE
CALL GFONT (KCCB,0.0,0.0,KDCB)

```

File: &AXLIN

File: &AXLOG

0
0 DONE
0 RETURN
0 END

```
0 CALL TDEFN
0 SUBROUTINE AXLOG (KCCB,KDCB,XDNY,X1,X2,Y1,Y2)
0
0 DRAW A FRAME DEFINED BY (X1,X2,Y1,Y2) WITH SEMI-LOG TIC MARK
0 EACH DECADE IN Y DIVIDED INTO 'MYTIC'(<=20) TIC MARKS
0 ASSURE 'BOTH' Y1,Y2 >0
0
0 DIMENSION KCCB(1),KDCB(1),LBUF(4),MTIC(4),YTIC(4),XDEL(4),YDEL(4),
0 DYLG(20),MYOFF(4),YOFF(2),NANTEH(3)
0
0 DATA NSEC/0/, NCR/2HGG/, NANTEH/2H10,2H ,2H /
0 DATA CHARN/25.0<EXP>0/, SUP/0.75<EXP>0/,
0 ASPEC/0.7<EXP>0/, SLANT/0.0<EXP>0/
0
0 ..... PRESET DATA
0 DATA YTSPAC/2.0<EXP>0/, TRATIO/0.02<EXP>0/
0 DATA MTIC/5/, NXGRD/25/, KGRID/0/
0
0 ..... SCALE CHARACTERS
0 CALL TSCAL (KCCB,XDNY,CHARN,CHITE,XLENG,YLENG)
0 XSPAN=X2-X1) YSPAN=Y2-Y1
0 CHITY=CHITE+YSPAN/YLENG) CHITX=CHITE+XSPAN/(XDNY*XLENG)
0 CHYFTR=CHITY*SUP
0
0 ..... TIC SIZE
0 TICX=XSPAN*TRATIO) TICY=YSPAN*TRATIO
0 MTIC(1)=TICX) YTIC(1)=0.0<EXP>0
0 MTIC(2)=0.0<EXP>0) YTIC(2)=TICX
0 MTIC(3)=TICX) YTIC(3)=0.0<EXP>0
0 MTIC(4)=0.0<EXP>0) YTIC(4)=TICX
0
0 ..... LINEAR SPACING
0 XTSPAC=XSPAN/NXGRD YDEL(1)=-1.0<EXP>0
0 XDEL(1)=0.0<EXP>0) YDEL(2)=0.0<EXP>0
0 XDEL(2)=XTSPAC) YDEL(3)=1.0<EXP>0
0 XDEL(3)=0.0<EXP>0) YDEL(4)=0.0<EXP>0
0 XDEL(4)=-XTSPAC)
0
0 ..... LOG SPACING
0 Y11=FLOAT(IFIX(Y1)) 0 TAKE THE INTEGER
0 Y11A=Y11
0 Y22=FLOAT(IFIX(Y2))
0 Y22A=Y22
0 IF (Y11.NE.Y1) [ IF (Y1.LT.0.0<EXP>0) Y11=Y11-1 ]
0 ELSE Y11=Y11+1
0 IF (Y22.NE.Y2) [ IF (Y2.LT.0.0<EXP>0) Y22=Y22-1 ]
0 ELSE Y22=Y22+1
0 NYGRD=Y22-Y11 0 NUMBER OF DECADES
0 YTSPAC=ANINT(ABS(YTSPAC),10.<EXP>0) 0 TIC SPACING
0
0 ..... COMMENT OUT UN-USED CODE
0 IF (YTSPAC.EQ.0.0<EXP>0) YTSPAC=2.0<EXP>0
0 IF (YTSPAC.EQ.10.0<EXP>0) [
0 MYCO=1 0 IF NO TICS
0 NYOFF(1)=1) NYOFF(2)=1
0 NYOFF(3)=1) NYOFF(4)=1
0 DYLG(1)=ALOG(YTSPAC)
0 ]
0 ELSE [
0 MYCO=NINT(IFIX(10.0<EXP>0/YTSPAC),20) 0 WITH TICS
0 YTSO=10.0<EXP>0/MYCO 0 TIC COUNT
0 0 ROUND OFF
0
0 MYCO=5
0 YTSO=YTSPAC
0 YTS=YTSO
0 DO N=1,MYCO [
0 DYLG(N)=ALOG(YTS) 0 TIC OFF SET IN LOG10
0 YTS=YTS+YTSO
0 ]
0 YOFF(2)=Y2-Y22 0 AXIS LIMIT OFF SET
0 YOFF(1)=Y1-Y11 0 TIC NEXT TO THE END
0 DO N=1,2 [
0 IF (YOFF(N).EQ.0.0<EXP>0) NYOFF(N)=0
0 ELSE [
0 J=1
0 JEND=0
0 WHILE ((J.LE.MYCO).AND.(JEND.EQ.0)) [
0 IF (YOFF(N).LE.DYLG(J)) JEND=J
0 ELSE J=J+1
0 ]
0 ]
0 ]
```

112

File: &CHECK

```
*CALL TUDFN
*IF NP1000
ERA (XYZ,0)
*ENDIF
SUBROUTINE CHECK
CHARACTERIZE DEVICE
*CALL TERA
*CALL TCOMM
*.....CHECK SURFACE REGION
CALL CROSS (I)
*.....CHECK FOR PUNCH THROUGH
CALL SADDL
*.....DONE
RETURN
END
```

File: &CHKDP

```
*CALL TUDFN
SUBROUTINE CHKDP (KINPL)
SCALE AND LIMIT IMPLANT PARAMETERS
*CALL TCOMM
DIMENSION DIFF(4),EAOVRK(4)
*.....SCALING FACTORS
DATA UN/1.0<EXP>-4/, SECND/60.0<EXP>0/, ZEROC/273.0<EXP>0/
*.....CONSTANTS
DATA DIFF/2.551<EXP>1, 5.230<EXP>0, 1.445<EXP>3, 1.903<EXP>3/,^
EAOVRK/4.430<EXP>4, 4.525<EXP>4, 5.100<EXP>4, 5.410<EXP>4/
*.....SCALE LOCAL IMPLANT LOCATION
IF (KINPL.EQ.2) [
KINPLO=KINPL0*UN
KINPLI=KINPLI*UN
IF (KINPLO.GT.KINPLI) [ T=KINPLO; KINPLO=KINPLI; KINPLI=T ]
]
*.....DETERMINE DOPANT TYPE
KDOPE=DOPE(KINPL)
IF ((KDOPE.EQ.1).OR.(KDOPE.EQ.6)) DTYPE=-1.0E0
ELSE DTYPE=1.0E0
*.....SCALING
RANGE(KINPL)=RANGE(KINPL)*UN
STNDV(KINPL)=ANXI(STNDV(KINPL)*UN,0.0<EXP>0)
DOSE(KINPL)=SIGN(DOSE(KINPL),DTYPE)
DRVIN(KINPL)=ANXI(DRVIN(KINPL)*SECND,0.0<EXP>0)
*.....DETERMINE THE DRIVE-IN DIFFUSIVITY
IF ((KDOPE.GE.1) .AND. (KDOPE.LE.4))
DCOEF(KINPL)=DIFF(KDOPE)*EXP(-EAOVRK(KDOPE)/(TEMP(KINPL)+ZEROC))
ELSE DCOEF(KINPL)=ANXI(DCOEF(KINPL),0.0<EXP>0)
*.....STEP APPROXIMATION
CALL ASTEP (KINPL)
*.....DONE
RETURN
END
```

IIS

File: &CHKGM

```
*CALL TUNDEFN
SUBROUTINE CHKGM
*
SCALE AND LIMIT GEOMETRY PARAMETERS
*CALL TCONMH
*
.... SCALING FACTOR
DATA UM/1.<EXP>-4/
*
.... SCALING AND LIMITING
TOX0=AMAX1(TOX0*UM,0.<EXP>0)
TOX1=AMAX1(TOX1*UM,0.<EXP>0)
XSOURC=AMAX1(XSOURC*UM,0.<EXP>0)
XDRAIN=AMAX1(XDRAIN*UM,0.<EXP>0)
XOXR=AMAX1(XOXR*UM,0.<EXP>0)
XCHANL=AMAX1(XCHANL*UM,0.<EXP>0)
YMAX=AMAX1(YMAX*UM,0.<EXP>0)
XMAX=XCHANL+XSOURC+XDRAIN
XGATE0=XGATE0*UM
XGATE1=XGATE1*UM
XOX0=XOX0*UM
XOX1=XOX1*UM
*
INTERCHANGE IF NECESSARY
IF (XGATE0.GT.XGATE1) [ T=XGATE0; XGATE0=XGATE1; XGATE1=T ]
IF (XOX0.GT.XOX1) [ T=XOX0; XOX0=XOX1; XOX1=T ]
*
DONE
RETURN
END
```

-21-

File: &CROSS

```
*CALL TUNDEFN
*IF HP1000
ENH (XYZ,0)
*ENDIF
SUBROUTINE CROSS (M)
*
CHARACTERIZE CROSS-SECTION AT Y-LOCATION M
*
*CALL TEMA
*CALL TCONMH
*
DATA UM/1.<EXP>4/, US0/700.<EXP>0/
*
TUOVT=VT300K+VT300K
YBARR=YPOS(N)*UM
*
.... SEARCH FOR POTENTIAL MINIMUM WITHIN CROSS SECTION
CALL PHIN (M,PHIN,LHIN)
XBARR=XPOS(LHIN)*UM
PBARR=POTS1(1,M)-PHIN
*
.... DETERMINE THE BASE REGION
CALL UBASE (LHIN,M,HB1,HB2)
UBARR=XPOS(HB2)-XPOS(HB1)
*
.... SEARCH FOR SOURCE DEPLETION REGION LIMIT
PHIN=POTS1(1,M)
POTX=POTS1(2,M)
NB2=1
WHILE ((NB2.LT.NSOURC).AND.((PHIN-POTX).LE.TUOVT)) [
NB2=NB2+1
POTX=POTS1(NB2+1,M)
]
*
.... SEARCH FOR DRAIN DEPLETION REGION LIMIT
PHIN=POTS1(MXMAX,M)
POTX=POTS1(MXMAX-1,M)
ND2=MXMAX
WHILE ((ND2.GT.NDRAIN).AND.((PHIN-POTX).LE.TUOVT)) [
ND2=ND2-1
POTX=POTS1(ND2-1,M)
]
*
.... ESTIMATE THE CURRENT IF ANY
CALL INTGR (LHIN,M,HB1,HB2,SUM)
HBARR=YPOS(HB2)-YPOS(HB1)
CINJ0=S*VT300K*US0/UBARR
CINJ=ABS(CINJ0*SUM)
*
SCALE AND WRITE THE RESULTS
CINJ=CINJ*UM
CINJ0=CINJ0*UM/ABS((CONC(LHIN,M)))
HBY1=YPOS(HB1)*UM
HBY2=YPOS(HB2)*UM
HBARR=HBY2-HBY1
HBY1=XPOS(HB1)*UM
HBY2=XPOS(HB2)*UM
UBARR=UBARR*UM
IF (M.EQ.1) WRITE (KONSOL,1030)
ELSE WRITE (KONSOL,1035) YBARR,M
WRITE (KONSOL,1000) PHIN,XBARR,LHIN,PBARR,CINJ0,UBARR,HBY1,HBY2,HB1,HB2
IF (CINJ.NE.0.<EXP>0) WRITE (KONSOL,1020) HBARR,HBY1,HBY2,HB1,HB2,CINJ
IF (M.EQ.1) [
US=HBY1-XPOS(NSOURC)*UM
UD=XPOS(NDRAIN)*UM-HBY2
WRITE (KONSOL,1050) US,UD
1050 FORMAT(3X,"Source depletion width =",F6.3,"um"
/3X,"Drain depletion width =",F6.3,"um"
)
]
*
.... FORMAT STATEMENTS
1030 FORMAT("==at surface==")
1035 FORMAT("==y-cross section at y =",F6.3,"um, (",I2,")")
1000 FORMAT(3X,"Potential minimum =",F7.3,"at X =",F6.3,"um, (",I2,")"
/3X,"Barrier height =",F7.3
/3X,"Current density =",1PF10.3," Amp/cm2"
/3X,"Barrier width =",0PF6.3,"um, from ",F6.3,"um to ",F6.3,"
"um, (",I2,")"
)
1020 FORMAT(3X,"Barrier depth =",0PF6.3,"um, from ",F6.3,"um to ",F6.3,"
"um, (",I2,")"
)
```

-22-

116

File: &CROSS

/.3X."Current / width = ".1PG10.3.^
" Anp/un. with US0=700 0 cm2/sec-V")

0
0.....DONE
RETURN
END

File: &DOPLC

```

*CALL TWDEFM
*IF HP1000
ENR (XYZ,0)
*ENDIF
SUBROUTINE DOPLC
LOCALIZED IMPLANT
*CALL TEMA
*CALL TCOMN
EQUIVALENCE (RNG, RANGE(2)),(SIGMA,STNDV(2)),(DIFF,DCOE(2)),^
(TIME,DRVIN(2)),(CPK, CPEAK(2)),(XJ,XJCT(2))
0
0
0.....STATEMENT FUNCTION
ARGL(X,Y)=SIGN(ANINI(ABS(X),ABS(Y)),X)
0
0.....CONSTANTS
DT=DIFF*TIME
ONSQDT=0.5<EXP>0/SQRT(DT)
STNDV2=SIGMA*SIGMA
FOURDT=(STNDV2*STNDV2)+(DT+DT+DT+DT)
B=RNG*SQRT(DT*DT)/FOURDT/SIGMA
IF (DT.NE.0.0<EXP>0) C=RNG/(FOURDT*B)
DXJ=AMAX1(XJ-RNG),0.0<EXP>0)+SIGMA+SIGMA
N1=LOC(XIMPL0-DXJ)
N2=LOC(XIMPL1+DXJ)
IF ((N1.LT.N2).AND.(N1.LT.NXMAX).AND.(N2.GT.1)) [
N1=MAX0(N1,1)
N2=MIN0(N2,NXMAX)
]
A1=XIMPL0+ONSQDT
A2=XIMPL1+ONSQDT
0
0.....IDEAL GAUSSIAN
DO N=1,NYMAX [
Y=YPOS(N)
ARG=(Y-RNG)*(Y-RNG)/FOURDT
CIMPLO=CPK*EXP(-ARGL(ARG,0.0<EXP>0))
0
0.....DRIVE IN, INCLUDE SURFACE REFLECTION
IF (DT.NE.0.0<EXP>0) [
CY=C*Y
CIMPLO=0.25<EXP>0+CIMPLO*(2.0<EXP>0+ERRFN(B+CY)+ERRFN(B-CY))
]
0
0.....LATERAL DIFFUSION
IF ((N1.GE.1).AND.(N2.LE.NXMAX)) DO M=N1,N2 [
IF (DT.NE.0.0<EXP>0) [
XA=XPOS(N)+ONSQDT
CIMPL=CIMPLO*(ERRFN(XA-A1)-ERRFN(XA-A2))
]
ELSE CIMPL=CIMPLO
CONC(N,M)=CONC(N,M)+CIMPL
]
]
0
0.....DONE
RETURN
END

```

```

*CALL TDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE DOPNG
*
* GENERATE DOPING PROFILES
*
*CALL TEMA
*CALL TCOMM
*
*.....LOAD SUBSTRATE CONCENTRATION
DO M=1,NXMAX; DO N=1,NYMAX; CONC(N,M)=CSUB
*
*.....IMPLANTATION
IF (DOSE(1).NE.0.<EXP>0) CALL DOPUL
IF (DOSE(2).NE.0.<EXP>0) CALL DOPLC
IF (DOSE(3).NE.0.<EXP>0) CALL DOPSD
*
*.....CALCULATE INPLANT RELATED PARAMETERS
CALL PARND
*
*.....DONE
RETURN
END

```

```

*CALL TDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE DOPSI
*
* GENERATE DOPING PROFILE USING SUPREM 8AVE FILE
*
*CALL TEMA
*CALL TCOMM
*
DIMENSION NSTRNG(20)
DIMENSION KDOPE(6),MESSG0(5,2),MESSG1(4,3)
*
DATA LMHSG0/3/,^
MESSG0/2Hb,2Hba,2Htr,2Het,2He ;^
2Hia,2Hpl,2Han,2Ht ,2H /
DATA LMHSG1/4/,^
MESSG1/2Hov,2Hor,2Hal,2Hl ,^
2Hlo,2Hco,2Hl',2Hd ,^
2Hsp,2Hc/,2Hdr,2Hn /
DATA KDOPE /2Hb ,2Ha ,2Hp ,2Hs ,2H+ ,2H- /
DATA KESC/033B/, KYEB/2HY /, UM/1.0<EXP>-4/
*
*.....DEFINE SOFT KEYS
*IF HP2448A
CALL SKEYP
*ENDIF
*
*.....GET SUBSTRATE TYPE
WRITE (KONSOL,1000) (MESSG0(K,1),K=1,LMHSG0)
1000 FORMAT('A2,' dopant (B=f1,A=f2,Ph=f3,Sp=f4,',^
'+(N-type)=f5,-(P-type)=f6) ? _')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
K=1; WHILE ((KANSUR.NE.KDOPE(K)).AND.(K.LE.6)) K=K+1
IF (K.GT.6) GO TO 801
IF ((K.EQ.1).OR.(K.EQ.6)) TYPE=-1.0<EXP>0
ELSE
TYPE= 1.0<EXP>0
IF (TYPE.EQ.-1.0<EXP>0) KB=6
ELSE
KB=5
*
*.....CHECK IF UNIFORM SUBSTRATE
WRITE (KONSOL,1010)
1010 FORMAT('Uniform substrate (Yes=f7/No=f8) ? _')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000 FORMAT(A1)
*
*.....IF UNIFORM, READ CSUB, LOAD CONCENTRATION ARRAY AND RESET FLAG
IF (KANSUR.EQ.KYES) [
WRITE (KONSOL,2010)
2010 FORMAT('Substrate concentration (in unit of 1E15 cm-3) ? _')
READ (KEYBRD,0) CSUB
*IF BATCH
WRITE (KONSOL,2011) CSUB
2011 FORMAT(1PG10.3)
*ENDIF
IF (CSUB.EQ.0.0<EXP>0) GO TO 802
CSUB=SIGN(CSUB+1.0<EXP>15,TYPE)
DO M=1,NXMAX; DO N=1,NYMAX; CONC(N,M)=CSUB
KSUB=0
]
*
*.....IF NOT UNIFORM, SET THE FLAG
ELSE [ KSUB=1; CSUB=0.0<EXP>0 ]
*
*.....ION IMPLANTATIONS
DO KIMPL=1,3 [
IF (KSUB.LE.0) [
WRITE (KONSOL,2020) (MESSG1(K,KIMPL),K=1,LMHSG1)
2020 FORMAT('Any',4A2,' implant (Yes=f7/No=f8) ? _')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF

```

```

0.....GET WINDOW OF LOCALIZED IMPLANT
      IF (KANSUR.EQ.KYES) [
        IF (KIMPL.EQ.2) [
          WRITE (KONSOL,2025)
          FORMAT("Localized implant: from <> to <> (un) ? -")
          READ (KEYBRD,*) XIMPLO,XIMPLI
2025
        *IF BATCH
          WRITE (KONSOL,2026) XIMPLO,XIMPLI
          FORMAT(IP2G15.3)
2026
        *ENDIF
          XIMPLO=XIMPLO*UN
          XIMPLI=XIMPLI*UN
          IF (XIMPLO.GT.XIMPLI) [ T=XIMPLO;XIMPLO=XIMPLI;XIMPLI=T ]
        ]
0.....GET DOPANT TYPE
      WRITE (KONSOL,2030)
      FORMAT("Implant dopant (B=f1,As=f2,Ph=f3,Sb=f4,^
        ^*(N-type)=F5,-(P-type)=F6) ? -")
      READ (KEYBRD,2000) KANSU1
2030
    *IF BATCH
      WRITE (KONSOL,2000) KANSU1
    *ENDIF
      IF ((KANSU1.EQ.KDOPE(1)).OR.(KANSU1.EQ.KDOPE(6)))
        DOPE(KIMPL)=6
      ELSE DOPE(KIMPL)=5
0.....GET STANDARD DEVIATION
      WRITE (KONSOL,2040)
      FORMAT("Implant STNDV(un) ? -")
      READ (KEYBRD,*) SD
2040
    *IF BATCH
      WRITE (KONSOL,2041) SD
      FORMAT(IPC10.3)
2041
    *ENDIF
      STNDV(KIMPL)=SD*UN
    ]
  ] ELSE DOPE(1)=K0
0.....GET DATA FILE NAME
      IF ((KSUB.EQ.1).OR.(KANSUR.EQ.KYES)) [
        WRITE (KONSOL,3010)
        FORMAT("Data file name ? -")
        READ (KEYBRD,3020) MSTRNG
        FORMAT(20A2)
3010
      *IF BATCH
        WRITE (KONSOL,3020) MSTRNG
      *ENDIF
0.....GET COLUMN INDEX
      WRITE (KONSOL,3030)
      FORMAT("Which column ? -")
      READ (KEYBRD,*) ICOLNH
3030
    *IF BATCH
      WRITE (KONSOL,3031) ICOLNH
      FORMAT(I2)
3031
    *ENDIF
0.....GENERATE PROFILE USING SUPREN SAVE FILE
      CALL REDSP (KIMPL,ICOLNH,MSTRNG)
    ] ELSE [ DOSE(KIMPL)=0.0(EXP)0; NJCT(KIMPL)=0.0(EXP)0 ]
0.....RESET SUBSTRATE FLAG
      IF (KSUB.EQ.1) KSUB=-1
    ]
0.....PREPROCESS PARAMETERS, RESET SUPREN FLAG
      CALL PARMS
      KSUPRN=0
0.....DONE
      RETURN
0.....ERROR
001
      CONTINUE
      WRITE (KONSOL,0001)
      FORMAT("Un-recognizable substrate dopant! Program terminated! **")

```

```

802 GO TO 800
      CONTINUE
      WRITE (KONSOL,8002)
8002 FORMAT("Zero substrate doping concentration! Program terminated! **")
800 CONTINUE
    *IF HP1000;IBATCH
8003 WRITE (KONSOL,8003) KESC
      FORMAT(I1,"a")
    *ELSE
      CALL EXEC (6)
    *ENDIF
      STOP
      END

```


File: LDG9SD

```
*CALL TDEFN
*IF HP1000
ENH(XYZ,0)
*ENDIF
SUBROUTINE DOP9D
0
0 SOURCE AND DRAIN IMPLANTATION
0
*CALL TEMA
*CALL TCOMM
0
EQUIVALENCE (RNG, RANGE(3)),(SIGMA,STNDV(3)),(DIFF,DCOEF(3)),^
(TIME,DRVIN(3)),(CPK, CPEAK(3)),(XJ, XJCT(3))
0
0.....STATEMENT FUNCTION
ARGL(X,Y)=SIGN(AMIN1(ABS(X),ABS(Y)),X)
0
0.....CONSTANTS
DT=DIFF*TIME
ONSQDT=0.5<EXP>0/SQRT(DT)
STNDV2=SIGMA*SIGMA
FOURDT=(STNDV2+STNDV2)*(DT+DT+DT+DT)
B=RNG*SQRT((DT+DT)/FOURDT)/SIGMA
IF (DT.NE.0.0<EXP>0) C=RNG/(FOURDT*B)
DXJ=AMAX1((XJ-RNG),0.0<EXP>0)+SIGMA+SIGMA+SIGMA
NS=LOC(DXJ)
ND=LOC(KCHANL-DXJ)
0
0.....IDEAL GAUSSIAN
DO N=1,NYMAX I
Y=YPOS(N)
ARG=(Y-RNG)*(Y-RNG)/FOURDT
CIMPL0=CPK*EXP(-ARGL(ARG,0.5<EXP>0))
IF (DT.NE.0.0<EXP>0) I
CY=C*Y
CIMPL0=0.25<EXP>0+CIMPL0*(2.0<EXP>0+ERRFN(B+CY)+ERRFN(B-CY))
]
0
0.....SIDE DIFFUSION AT SOURCE JUNCTION
DO N=1,NS I
IF (DT.NE.0.0<EXP>0) I
ARG=XPOS(N)*ONSQDT
CIMPL=CIMPL0*(1.0<EXP>0+ERRFN(ARG))
]
ELSE CIMPL=CIMPL0
CONC(N,N)=CONC(N,N)+CIMPL
]
0
0.....SIDE DIFFUSION AT DRAIN JUNCTION
DO N=ND,NXMAX I
IF (DT.NE.0.0<EXP>0) I
ARG=(XPOS(N)-KCHANL)*ONSQDT
CIMPL=CIMPL0*(1.0<EXP>0+ERRFN(ARG))
]
ELSE CIMPL=CIMPL0
CONC(N,N)=CONC(N,N)+CIMPL
]
]
0
0.....DONE
RETURN
END
```

File: LDOPUL

```
*CALL TDEFN
*IF HP1000
ENH(XYZ,0)
*ENDIF
SUBROUTINE DOPWL
0
0 OVERALL IMPLANT
0
*CALL TEMA
*CALL TCOMM
0
EQUIVALENCE (RNG, RANGE(1)),(SIGMA,STNDV(1)),(DIFF,DCOEF(1)),^
(TIME,DRVIN(1)),(CPK, CPEAK(1))
0
0.....STATEMENT FUNCTION
ARGL(X,Y)=SIGN(AMIN1(ABS(X),ABS(Y)),X)
0
0.....CONSTANTS
DT=DIFF*TIME
STNDV2=SIGMA*SIGMA
FOURDT=(STNDV2+STNDV2)*(DT+DT+DT+DT)
B=RNG*SQRT((DT+DT)/FOURDT)/SIGMA
IF (DT.NE.0.0<EXP>0) C=RNG/(FOURDT*B)
0
0.....IDEAL GAUSSIAN
DO N=1,NYMAX I
Y=YPOS(N)
ARG=(Y-RNG)*(Y-RNG)/FOURDT
CIMPL=CPK*EXP(-ARGL(ARG,0.5<EXP>0))
0
0.....DRIVE-IN, INCLUDE THE REFLECTION AT THE SURFACE
IF (DT.NE.0.0<EXP>0) I
CY=C*Y
CIMPL=CIMPL0*(1.0<EXP>0+0.5<EXP>0*(ERRFN(B+CY)+ERRFN(B-CY)))
]
0
0.....LOAD CONCENTRATION ARRAY
DO N=1,NXMAX I
CONC(N,N)=CONC(N,N)+CIMPL
]
0
0.....DONE
RETURN
END
```

```

*CALL TUNDEFN
FUNCTION ERRFN(X)
      CLOSE FORM APPROXIMATION OF ERROR FUNCTION
      COEFFICIENTS OF THE EQUIVALENT POLYNOMIAL
      DATA COEFF1/0.0705230784<EXP>0/,COEFF2/0.0422820123<EXP>0/,
            COEFF3/0.0092705272<EXP>0/,COEFF4/0.0001520143<EXP>0/,
            COEFF5/0.0002765672<EXP>0/,COEFF6/0.0000430638<EXP>0/
      CALCULATE THE POWERS OF THE ABSOLUTE X
      X1=ABS(X)
      X2=X1*X1
      X3=X2*X1
      X4=X3*X1
      X5=X4*X1
      X6=X5*X1
      TERMS USED IN THE CLOSE FORM APPROXIMATION
      ARG1=1.0<EXP>0+COEFF1*X1+COEFF2*X2+COEFF3*X3+
            COEFF4*X4+COEFF5*X5+COEFF6*X6
      ARG2=ARG1*ARG1
      ARG4=ARG2*ARG2
      ARG8=ARG4*ARG4
      ARGH=ARG8*ARG8
      THE CLOSE FORM APPROXIMATION
      ERRFN=1.0<EXP>0-1.0<EXP>0/ARGH
      IF (X.LT.0.0<EXP>0) ERRFN=-ERRFN
      DONE
      RETURN
      END

```

```

*CALL TUNDEFN
SUBROUTINE GETPA
      READ IN PARAMETERS
      *CALL TCOMMH
      DIMENSION MESSAG(9,2)
      DATA KYES/2HY /,LEHMSG/9/,
            MESSAG/2Hds,2Hvi,2Hce,2H s,2Htr,2Huc,2Htu,2Hre,2H? /,
            2Hdo,2Hpi,2Hng,2H p,2Hro,2Hfi,2Hle,2H? ,2H /
      CHECK INPUT OPTION
      WRITE (KONSOL,1000)
1000  FORMAT("Input from the console (Yes=f7/No=f8) ? _")
      READ (KEYBRD,2000) KANSUR
2000  FORMAT(A1)
      *IF BATCH
            WRITE (KONSOL,2000) KANSUR
      *ENDIF
      INPUT FROM CONSOLE
      NEUNSH=1
      KREAD=1
      IF (KANSUR.EQ.KYES) (
            KREAD=0
      )
      READ IN STRUCTURE PARAMETERS
      IF (KLOOP.NE.1) (
            WRITE (KONSOL,3000) (MESSAG(K,1),K=1,LEHMSG)
            FORMAT("Redefine the ",9A2," (Yes=f7/No=f8) ? _")
            READ (KEYBRD,2000) KANSUR
      *IF BATCH
            WRITE (KONSOL,2000) KANSUR
      *ENDIF
            )
            IF (KANSUR.EQ.KYES) (
                  IF (KLOOP.EQ.1) CALL REDCH
                  ELSE
                        CALL RDFCH
            )
            ELSE NEUNSH=0
      )
      READ IN PROFILE PARAMETERS
      KANSUR=KYES
      IF (KLOOP.NE.1) (
            WRITE (KONSOL,3000) (MESSAG(K,2),K=1,LEHMSG)
            READ (KEYBRD,2000) KANSUR
      *IF BATCH
            WRITE (KONSOL,2000) KANSUR
      *ENDIF
            )
            IF (KANSUR.EQ.KYES) NEUDOP=1
            ELSE
                  NEUDOP=0
            IF (NEUDOP.EQ.1) (
                  WRITE (KONSOL,3010)
                  READ (KONSOL,2000) KANSUR
                  FORMAT("Use SUPREM generated profile (Yes=f7/No=f8) ? _")
                  IF (KANSUR.EQ.KYES) KSUPRM=1
                  ELSE
                        KSUPRM=0
            )
            IF ((NEUDOP.EQ.1).AND.(KSUPRM.EQ.0)) (
                  IF (KLOOP.EQ.1) CALL REDDP
                  ELSE
                        CALL RDFDP
            )
            )
      )
      INPUT FROM FILE
      ELSE CALL REDF1
      DONE
      RETURN
      END

```

```

*CALL TWDEFN
*IF NP1000
ENR(KYZ,0)
*ENDIF
SUBROUTINE INDEP (LOC,KTYPE,TOX,PHIGB)
*
* INITIALIZE 1-D POTENTIAL ARRAY IN DEPLETION CHANNEL REGION
*
*CALL TEHA
*CALL TCDHNN
*
*..... CALCULATE SOME USEFUL QUANTITIES
COX=EPSI02/TOX
PHJCT=AMAX1(PHIB+PHIF(KTYPE)+VSB,0.0<EXP>0)
GAMMA=GAMM(KTYPE)/COX
ALFA=ALPHA(KTYPE)
PHIC=PHIP(KTYPE)
IF (KTYPE.LE.2) I
  WIMP=NJCT(KTYPE)
  CIMP=CSTEP(KTYPE)
  VIMP=Q*CIMP/COX
]
ELSE I
  WIMP=WBURF(1)
  CIMP=CBURF(1)
  VIMP=Q*CIMP/COX
]
CD=CIMP-CSUB
CDONCA=CD/CSUB
UM=ALPH0*SQRT(PHJCT/(CDONCA*(1.0<EXP>0+CDONCA)))
QM=Q*CD*ARINI(UM,WIMP)
UP=ALPH0*SQRT(PHJCT/(1.0E0+1.0<EXP>0/CDONCA))
QP=Q*CSUB*UP
*
*..... DETERMINE FLAT-BAND CONDITION
IF (UM.LE.WIMP) VGBFB=VFB+PHJCT
ELSE VGBFB=VFB+(QP-QM)/COX-VIMP+ALPH0*(WIMP+UP)*(WIMP+UP)
DELCC=COX*(PHIGB-VGBFB)/Q
*
*..... SURFACE ACCUMULATION
IF (PHIGB.GE.VGBFB) DELPH0=VT300K*ALOG(DELCC/CD-1.0<EXP>0)
*
*..... SURFACE DEPLETION
ELSE I
  IF (UM.LE.WIMP) I
    KP=Q
    UG=-DELCC/CD
    IF (UG.LT.WIMP) DELPH0=(-ALFA+ALPH0)*UG*UG
    ELSE KP=1
  ]
  ELSE KP=1
  IF (KP.EQ.1) I
    UG=-DELCC/CSUB
    IF (UG.LE.UP) I
      DELPH0=0.0<EXP>0
      UP=UP-UG
    ]
  ]
]
*
*..... ACCUMULATION IN SUBSTRATE
ELSE I
  DELPH0=VT300K*ALOG(-DELCC/CSUB-1.0<EXP>0)
  UP=0.0<EXP>0
]
]
*
*..... POTENTIALS DUE TO DEPLETED SUBSTRATE
VN=AMAX1(WIMP-UM,0.0<EXP>0)
VP=WIMP+UP
NM=MAX0(LOCY(VN),1)
NP=LOCY(VP)
IF (VN.NE.YPOS(NM)) NM=NM+1
IF (VP.NE.0.0<EXP>0) I
  DO M=NM,NP I
    Y=YPOS(M)
    POTSI(LOC,M)=ALPH0*(VP-Y)*(YP-Y)
    CARRIE(LOC,M)=0.0<EXP>0
  ]
  PHIP=ALPH0*UP*UP
]
]

```

```

*
*..... POTENTIAL DUE TO ACCUMULATED SUBSTRATE
ELSE I
  DO M=NM,NP I
    POTSI(LOC,M)=DELPH0
    CARRIE(LOC,M)=0.0<EXP>0
  ]
  PHIP=DELPH0
]
*
*..... POTENTIAL DUE TO DEPLETED N-REGION
NI=LOCY(WIMP)
DO M=NM,NI I
  Y=YPOS(M)
  POTSI(LOC,M)=POTSI(LOC,M)-ALFA*(WIMP-Y)*(WIMP-Y)
]
PNIN=PHIP+ALFA*UM*UM
*
*..... BURIED CHANNEL
NM=NM-1
IF (NM.GE.1) I
  DO M=1,NM I
    POTSI(LOC,M)=PNIN
    CARRIE(LOC,M)=-CONC(LOC,M)
  ]
]
*
*..... DEPLETED SURFACE
IF (DELPH0.LT.0.0<EXP>0) I
  NG=LOCY(UG)
  ALFS=-ALFA+ALPH0
  IF (NG.GE.1) I
    DO M=1,NG I
      Y=YPOS(M)
      POTSI(LOC,M)=POTSI(LOC,M)+ALFS*(Y-UG)*(Y-UG)
      CARRIE(LOC,M)=0.0<EXP>0
    ]
  ]
]
*
*..... ACCUMULATED SURFACE
IF (DELPH0.GT.0.0<EXP>0) I
  POTSI(LOC,1)=POTSI(LOC,1)+DELPH0
  CARRIE(LOC,M)=-CONC(LOC,M)-Q*DELCC
]
]
*
*..... NEUTRAL SUBSTRATE
NM=NP+1
IF (NM.LE.NYMAX) I
  DO M=NM,NYMAX I
    POTSI(LOC,M)=0.0<EXP>0
    CARRIE(LOC,M)=-CONC(LOC,M)
  ]
]
*
*..... DONE
RETURN
END

```



```

*CALL TUDFN
*IF HP1000
EMAC(XYZ,0)
*ENDIF
SUBROUTINE INENH (LOC,KTYPE,TOX,PHIGB)
*
* INITIALIZE 1-D POTENTIAL ARRAY IN ENHANCEMENT CHANNEL REGION
*
*CALL TERA
*CALL TCONHH
*
*..... CALCULATE SOME USEFUL QUANTITIES
COX=EPSI02/TOX
IF (KTYPE.EQ.0) [
PHIBI=ANAXI(2.5<EXP>0)*PHIS+VSB,0.0<EXP>0) 0 case of uniform substrate
GAMMA=GAMNB/COX 0 effective body-effect coeff
ALFA=ALPHB 0 effective dept-rgn width coeff
VBC=0.0<EXP>0 0 knee-voltage of vsb
PHIC=0.0<EXP>0 0 built-in potential at vbc
WIMP=0.0<EXP>0 0 depth of implant region
CIMP=0.0<EXP>0 0 concentration of implant
VIMP=0.0<EXP>0 0 shift in vth by implant
]
ELSE [
PHIBI=ANAXI(PHIB+PHIF(KTYPE)*1.5<EXP>0+VSB,0.0<EXP>0) 0 case of non-uniform substrate
GAMMA=GAMN(KTYPE)/COX
ALFA=ALPHA(KTYPE)
VBC =VBCRT(KTYPE)
PHIC=PHIMP(KTYPE)
IF (KTYPE.LE.2) [
WIMP=NJCT(KTYPE)
CIMP=CSIEP(KTYPE)
VIMP=-G*CIMP/COX
]
ELSE [
WIMP=WBURF(1)
CIMP=CBURF(1)
VIMP=-G*CIMP/COX
]
]
IF (VSB.LE.VBC)VTH=VFB+PHIBI+GAMMA*SQRT(PHIBI)
ELSE
VTH=VFB+PHIBI+VIMP+GAMNB*SQRT(ANAXI(PHIBI-PHIC,0.0<EXP>0))
*
*..... WEAK INVERSION CASE
IF (PHIGB.LE.VTH) [
IF (VSB.LE.VBC) [
G=GAMNA
VCBEFF=PHIGB-VFB
DPHI=0.0<EXP>0
VTEFF=VT300K
IF (KTYPE.NE.0) [
DPHI=PHIF(KTYPE)-PHIB
VTEFF=VT300K+CSUB/(CIMP+CSUB)
]
]
ELSE [
G=GAMNB
VCBEFF=PHIGB-VFB+PHIC
DPHI=0.0<EXP>0
VTEFF=VT300K+PHIC
]
G2OH2=0.5<EXP>0*G*G
SQARC=ANAXI(VCBEFF+0.5<EXP>0*G2OH2-DPHI-VTEFF,0.0<EXP>0)
PHIS=VCBEFF+G2OH2-G*SQARC
]
*
*..... STRONG INVERSION CASE
ELSE [
ARG=(PHIGB-VFB-PHIBI)+(PHIGB-VFB-PHIBI)/(GAMNA+GAMMA+VT300K)
PHIS=PHIBI+VT300K*ALOC(ANAXI(ARG,1.0<EXP>-10))
]
*
*..... ASSIGN POTENTIAL ARRAY
POTSI(LOC,1)=PHIS
CARRIE(LOC,1)=0.0<EXP>0
UDPL=SQRT(PHIS/(ALPHB+ALPHA(KTYPE)))
IF (UDPL.GT.WIMP) UDPL=SQRT(ANAXI(PHIS-PHIC,0.0<EXP>0)/ALPHB)
DO N=2,NMAX [
Y=VFB(N)
IF (Y.LT.UDPL) [

```

```

POTSI(LOC,N)=ALPHB*(UDPL-Y)*(UDPL-Y)
CARRIE(LOC,N)=0.0<EXP>0
IF (Y.LT.WIMP) POTSI(LOC,N)=POTSI(LOC,N)+ALFA*(WIMP-Y)*(WIMP-Y)
]
ELSE [
POTSI(LOC,N)=0.0<EXP>0
CARRIE(LOC,N)=-CONC(LOC,N)
]
]
]
*..... DONE
RETURN
END

```

```

*CALL TUDEFH
*IF HP1000
ENA (XYZ,0)
*ENDIF
SUBROUTINE INEQU (N1,N2,NR,KMSG)
  0
  0 LOAD POTENTIAL AND CARRIER ARRAYS FROM N1 TO N2 AS NR
  0
  0 *CALL TEMA
  0 *CALL TCOMH
  0
  0 DATA UM/1.0<EXP>4/
  0
  0 IF (N1.NE.N2) DO M=N1,N2; DO N=1,MYNAX [
  0   POTSI (N,M)=POTSI (NR,M)
  0   CARRIE(N,M)=CARRIE(NR,M)
  0 ]
  0 ELSE DO M=1,MYNAX [
  0   POTSI (N1,M)=POTSI (NR,M)
  0   CARRIE (N1,M)=CARRIE (NR,M)
  0 ]
  0 X1=XPOS(N1)*UM
  0 X2=XPOS(N2)*UM
  0 NR=XPOS(NR)*UM
  0 IF (KMSG.NE.0) WRITE (KONSOL,1000) X1,N1,X2,N2,XR,NR
1000 FORMAT('Equal potential region between ',
          'F6.2,"un(",I2,") and ',F6.2,"un(",I2,")')
  0
  0 ..... DONE
  0 RETURN
  0 END

```

```

*CALL TUDEFH
*IF HP1000
ENA (XYZ,0)
*ENDIF
SUBROUTINE INITL (KMSG)
  0
  0 INITIALIZE POTENTIAL DISTRIBUTION
  0
  0 *CALL TEMA
  0 *CALL TCOMH
  0
  0 DATA UM/1.0<EXP>4/, KYES/2HY /
  0
  0 KPASS=1
  0 ..... CHECK IF ENVOKE LOCAL ITERATION
  0   KLITR=51
  0   IF (RELAX1.EQ.1) [
  0     WRITE (KONSOL,1030)
  0     READ (KEYBRD,2000) KANSUR
  0 *IF BATCH WRITE (KONSOL,2000) KANSUR
  0 *ENDIF
  0   IF (KANSUR.EQ.KYES) [
  0     WRITE (KONSOL,1040)
  0     READ (KEYBRD,0) KLITR
  0 *IF BATCH
1041 WRITE (KONSOL,1041) KLITR
  0 *ENDIF
  0   WRITE (KONSOL,1050)
  0   READ (KEYBRD,2000) KANSUR
  0 *IF BATCH
  0   WRITE (KONSOL,2000) KANSUR
  0 *ENDIF
  0   IF (KANSUR.EQ.KYES) KINSC0=1
  0   ELSE
  0     KINSC0=0
  0 ]
  0 ]
1030 FORMAT('Envoke local iteration (Yes=f7/No=f6) ? -')
1040 FORMAT('Start from ( ) iteration ( ) ?? -')
1050 FORMAT('Convergence information per grid (Yes=f7/No=f8) ? -')
2000 FORMAT(A1)
  0
  0 ..... DEFINE SURFACE DEPLETION REGIONS
  0 CALL UDEPL (US0,US1,UD0,ND1)
  0 IF ((NSOURC.GE.1).AND.(ABS(DOSE(3)).GT.1.0<EXP>0)) [
  0   NS0=XPOS(NSOURC)-US0
  0   NS0=LOCK(NS0)
  0   NS1=XPOS(NSOURC)+US1
  0   NS1=LOCK(NS1)
  0   IF (NS1.NE.XPOS(NS1)) NS1=NS1+1
  0   NS0=MAX0(NS0,2)
  0   NS1=MIN0(NS1,NDRAIN-1)
  0 ]
  0 ELSE [
  0   NS1=XPOS(NSOURC)
  0   NS0=NS1-US1
  0   NS1=NSOURC
  0   NS0=LOCK(NS0)
  0   NS0=MAX0(NS0,2)
  0 ]
  0 IF ((NDRAIN.LE.NXNAX).AND.(ABS(DOSE(3)).GT.1.0<EXP>0)) [
  0   ND0=XPOS(NDRAIN)+UD0
  0   ND0=LOCK(ND0)
  0   ND1=XPOS(NDRAIN)-UD1
  0   ND1=LOCK(ND1)
  0   IF (ND0.NE.XPOS(ND0)) ND0=ND0+1
  0   ND0=MIN0(ND0,NXNAX-1)
  0   ND1=MAX0(ND1,NSOURC+1)
  0 ]
  0 ELSE [
  0   XD1=XPOS(NDRAIN)
  0   XD0=XD1+UD1
  0   ND1=NDRAIN
  0   ND0=LOCK(XD0)
  0   ND0=MIN0(ND0,NXNAX-1)
  0 ]
  0 XC=0.5<EXP>0*(XPOS(NS1)+XPOS(ND1))
  0 MC=LOCK(XC)

```

File: 6IHITL

```
      NC=MAX0(NC,NS1)
0..... INITIALIZE BOUNDARY PLANE AT SOURCE END
      CALL POSHI (1,KPASS,KLITR,KMSG)
0..... INITIALIZE MIDDLE CROSS-SECTION OF CHANNEL REGION IF EXISTS;
      OTHERWISE, INNER BOUNDARY OF DRAIN-CONTROLLED DEPLETION REGION
      IF (ND1.GT.NS1) CALL POSHI (NC, KPASS,KLITR,KMSG)
      ELSE
        CALL POSHI (ND1,KPASS,KLITR,KMSG)
0..... INITIALIZE BOUNDARY PLANE AT DRAIN END
      CALL POSHI (MXMAX,KPASS,KLITR,KMSG)
0..... LOAD POTENTIAL AND CARRIER ARRAYS IN SOURCE, DRAIN AND CHANNEL REGIONS
      CALL INEQU (2,NS0,1,KMSG)
      CALL INEQU (ND0,MXMAX-1,MXMAX,KMSG)
      IF (ND1.GT.NS1) [
        IF (NS1.NE.NC) CALL INEQU (NS1,NC-1,NC,KMSG)
        IF (ND1.NE.NC) CALL INEQU (NC+1,ND1,NC,KMSG)
      ]
0..... SOURC- AND DRAIN-CONTROLLED DEPLETION REGIONS
      CALL INLAT (ND1,ND0)
      ND0=XPOS(ND0)+UN
      ND1=XPOS(ND1)+UN
      IF (KMSG.GT.0) WRITE (KONSOL,3000) XD1,ND1,XD0,ND0
      IF (ND1.GT.NS1) CALL INLAT (NS0,NS1)
      ELSE [
        CALL INLAT (NS0,NC)
        NS1=NC
        ND1=NC
      ]
      NS0=XPOS(NS0)+UN
      NS1=XPOS(NS1)+UN
      IF (KMSG.GT.0) WRITE (KONSOL,3000) NS0,NS0,NS1,NS1
3000  FORMAT ('Lateral depletion layer between ',F6.2,'um(',I2,') and ',
           ',F6.2,'um(',I2,')')
0..... INITIALIZE OXIDE
      CALL INOXD
0..... DONE
      RETURN
      END
```

-41-

File: 6INLAT

```
*CALL TUDFN
*IF HPI000
  EMA (XYZ,0)
*ENDIF
      SUBROUTINE INLAT (N1,N2)
0..... INITIALIZE LATERAL DEPLETION REGIONS
0..... CALL TENA
0..... CALL TCONMH
0..... DETERMINE POLARITY
      POT1=POTSI(N1,1)
      POT2=POTSI(N2,1)
      IF (POT1.NE.POT2) [
        WDS=ABS((XPOS(N2))-XPOS(N1))
        ALPHAX=WDS+WDS/ABS(POT1-POT2)
      ]
0..... ASSIGN THE POTENTIAL
      DO M=1,NYMAX [
        POT1=POTSI(N1,M)
        POT2=POTSI(N2,M)
        N1=XPOS(N1)
        N2=XPOS(N2)
        XTOTL=ABS(N2-N1)
        IF (POT1.GT.POT2) [
          NL=N1; NL1=N1+1; NR=N2; NR1=N2-1; HD=1
          XL=N1; POTL=POT1; PTR=POT2
        ]
        ELSE [
          NL=N2; NL1=N2-1; NR=N1; NR1=N1+1; HD=-1
          XL=N2; POTL=POT2; PTR=POT1
        ]
        UDY=SQRT(ALPHAX*(POTL-PTR))
        IF (ND.GT.0) FOR (N=NL1; N<=NR1; N=N+ND) [
          X=ABS(XPOS(N))-XL
          IF (X.LT.UDY) [
            POTSI(N,M)=(UDY-X)*(UDY-X)/ALPHAX+PTR
            CARRIE(N,M)=0.0<EXP0
          ]
          ELSE [
            POTSI(N,M)=PTR
            CARRIE(N,M)=CARRIE(NR,M)
          ]
        ]
        ELSE FOR (N=NL1; N=NR1; N=N+ND) [
          X=ABS(XPOS(N))-XL
          IF (X.LT.UDY) [
            POTSI(N,M)=(UDY-X)*(UDY-X)/ALPHAX+PTR
            CARRIE(N,M)=0.0<EXP0
          ]
          ELSE [
            POTSI(N,M)=PTR
            CARRIE(N,M)=CARRIE(NR,M)
          ]
        ]
      ]
0..... EQUALPOTENTIAL
      ELSE DO N=N1,N2; DO M=1,NYMAX [
        POTSI(N,M)=POTSI(N1,M)
        CARRIE(N,M)=CARRIE(N1,M)
      ]
0..... DONE
      RETURN
      END
```

-42-

File: &INORD

```
•CALL TDEFN
•IF HP1000
EHA(XYZ,0)
•ENDIF
SUBROUTINE INORD
•
INITIALIZE OXIDE POTENTIAL ARRAYS
•
•CALL TEHA
•CALL TCONM
•
•..... UNDER GATE ELECTRODE
IF (NGATE0.NE.NGATE1) DO N=NGATE0,NGATE1 [
PHIS=POTSIC(N,1)
DELOX1=DELOX(N,1)
DELOXT=DELOX1+DELOX(N,2)
POTOX(N,2)=VGD
POTOX(N,1)=(VGD-PHIS)*DELOX1/DELOXT+PHIS
]
•
•..... OUTSIDE GATE ELECTRODE
NG0=NGATE0-1
NG1=NGATE1-1
NXXAX1=NXXAX-1
DO KK=1,2 [
IF (KK.EQ.1) [ NN1=2] NN2=NG0 ]
ELSE [ NN1=NG1] NN2=NXXAX1 ]
DO N=NN1,NN2 [
PHIS=POTSIC(N,1)
DELOX1=DELOX(N,1)
DELOXT=DELOX1+DELOX(N,2)
POTOX1=CSONI(N,1)*(PHIS+PHIS)
POTOX(N,1)=POTOX1
POTOX(N,2)=CSONI(N,2)*POTOX1
]
]
•..... DONE
RETURN
END
```

File: &INSAD

```
•CALL TDEFN
•IF HP1000
EHA(XYZ,0)
•ENDIF
SUBROUTINE INSAD (LOC,PHIBI)
•
INITIALIZE POTENTIAL ARRAY IN SOURCE AND/OR DRAIN
•
•CALL TEHA
•CALL TCONM
•
•..... ASSIGN POTENTIAL ARRAY BASED ON ABRUPT JUNCTION ASSUMPTION
UDEPL=SQRT(AHAXI(PHIBI,0.0*(EXP)0)/ALPHB)
DO M=1,NYMAX [
CONCX=CONC(LOC,M)
TPX=SIGN(1.0*(EXP)0,CONCX)
IF (TPX.NE.TYPE) [
POTSIC(LOC,M)=PHIBI
CARRIE(LOC,M)=-CONCX
]
ELSE [
Y=YPOS(M)
IF (Y.LT.UDEPL) [
POTSIC(LOC,M)=(UDEPL-Y)*(UDEPL-Y)*ALPHB
CARRIE(LOC,M)=0.0*(EXP)0
]
ELSE [
POTSIC(LOC,M)=0.0*(EXP)0
CARRIE(LOC,M)=-CONCX
]
]
]
]
•..... DONE
RETURN
END
```

File: &INTGR

```
*CALL TUDFN
*IF NPI000
ENH (XYZ,0)
*ENDIF
0
0 SUBROUTINE INTGR (N,H,NB1,NB2,SUM)
0
0 INTEGRATE CONDUCTION CARRIERS
0
0 *CALL TENA
0 *CALL TCONMH
0
0 ..... LOCATE UPPER BOUNDARY
0 NB1=N
0 TYPC=SIGN(1.0<EXP>0,(CARRIE(N,H)))
0 WHILE ((NB1.GT.1).AND.(TYPC.EQ.TYPE)) [
0 NB1=NB1-1
0 TYPC=SIGN(1.0<EXP>0,(CARRIE(N,NB1)))
0 ]
0 IF (NB1.NE.N) NB1=NB1+1
0
0 ..... INTEGRATE UP TO THE ZERO CARRIER POINT
0 NB2=NB1
0 CARRO=CARRIE(N,NB2)
0 SUM=0.0<EXP>0
0 TYPC=SIGN(1.0<EXP>0,(CARRIE(N,H)))
0 WHILE ((NB2.LT.NYNAX).AND.(TYPC.EQ.TYPE)) [
0 NB2=NB2+1
0 OLDCAR=CARRO
0 CARRO=CARRIE(N,NB2)
0 TYPC=SIGN(1.0<EXP>0,CARRO)
0 SUM=SUM+0.5<EXP>0*DELY(NB2-1)*(OLDCAR+CARRO)
0 ]
0
0 ..... DONE
0 RETURN
0 END
```

-45-

File: &ITER0

```
*CALL TUDFN
SUBROUTINE ITER0 (PHI,PHIA,QOVRE,CDOPE,ABSTL,HITRB,KITR)
0
0 NEWTON-RALPHSON ITERATION AT A MESH POINT
0
0 *CALL TCONMH
0
0 ..... STATEMENT FUNCTION
0 ARGL(X,Y)=SIGN(AMINI(ABS(X),ABS(Y)),X)
0
0 HITRB=1
0 KGO=1
0 REPEAT [
0 ARGP=ARGL(-(PHI-PHIFP)/VT300K,85.0<EXP>0)
0 ARGH=ARGL( (PHI-PHIFN)/VT300K,85.0<EXP>0)
0 CONCP=CSUB*EXP(ARCP)
0 CONCN=CHINRO*EXP(ARGH)
0 FVAL=PHI-PHIA-QOVRE*(CDOPE+CONCP-CONCN)
0 DVAL=1.0<EXP>0+QOVRE*(CONCP+CONCN)/VT300K
0 DELPHI=FVAL/DVAL
0 IF (ABS(DELPHI).GT.ABSTL) [
0 PHI=PHI-DELPHI
0 HITRB=HITRB+1
0 IF (HITRB.GE.KITR) [
0 HITRB=HITRB-1
0 KGO=0
0 ]
0 ]
0 ELSE KGO=0
0 ] UNTIL (KGO.EQ.0)
0
0 ..... DONE
0 CDOPE=CONCP-CONCN
0 RETURN
0 END
```

-46-

File: SLABLH

```
*CALL TUDFNH
SUBROUTINE LABLH (KCCB,KDCB,LABL,KFONT,CHITE,XTLEN,MFONT)
GET LENGTH AND FONT COUNT OF LABEL ARRAY "LABL" OF SPEC "KFONT"
DIMENSION KCCB(1),KDCB(1),LABL(1),KFONT(1),NAMFNT(3),NUMBR(6)
DATA NXFNT/2/, NYFNT/10/, NSEC /0/, NCR/2HGG/, ^
NAMFNT/2HFO,2HNT,2M /, NUMBR /2H1 ,2H2 ,2H3 ,2H4 ,2H5 ,2H6 /, ^
ASPEC/0.7<EXP>0/, SLANT/0.0<EXP>0/, SUP/0.75<EXP>0/

NS=1
KEND=0
MFONT=1
KFOLD=0
XTLEN=0.0<EXP>0
CALL LDIR (KCCB,0.0<EXP>0)
REPEAT (
NP=(MFONT-1)*MXFNT+1
NC=KFONT(NP)
IF (NC.EQ.0) KEND=1
ELSE (
KF=KFONT(NP+1)
IKF=IABS(KF)
IF (IKF.NE.KFOLD) (
NAMFNT(3)=NUMBR(IKF)
CALL CFONT (KCCB,NAMFNT,NSEC,NCR,KDCB)
)
IF (KF.LT.0)
CALL CSIZE (KCCB,CHITE+SUP,ASPEC,SLANT,0)
CALL GLEN (KCCB,LABL,NS,NC,XT,VT,KDCB)
IF (KF.LT.0)
CALL CSIZE (KCCB,CHITE,ASPEC,SLANT,0)
XTLEN=XTLEN+XT
NS=NS+NC
MFONT=MFONT+1
KFOLD=IKF
)
) UNTIL ((MFONT.GT.NYFNT).OR.(KEND.EQ.1))
MFONT=MFONT-1
IF (MFONT.NE.0) CALL CFONT (KCCB,0.0.0.KDCB)
RETURN
END
```

File: SLABUR

```
*CALL TUDFNH
SUBROUTINE LABUR (KCCB,KDCB,LABL,KFONT,CHITE,MFONT,XOFF,YOFF)
WRITE OUT LABEL ARRAY LABL WITH SPEC IN "KFONT" UP TO "MFONT" FONTS
DIMENSION KCCB(1),KDCB(1),LABL(1),KFONT(1),NAMFNT(3),NUMBR(6)
DATA NXFNT/2/, NYFNT/10/, NSEC /0/, NCR/2HGG/, ^
NAMFNT/2HFO,2HNT,2M /, NUMBR /2H1 ,2H2 ,2H3 ,2H4 ,2H5 ,2H6 /, ^
ASPEC/0.7<EXP>0/, SLANT/0.0<EXP>0/, SUP/0.75<EXP>0/

XOFF=XOFF/3.0<EXP>0
YOFF=YOFF/3.0<EXP>0
MFOLD=0
NS=1
DO K=1,MFONT (
KK=(K-1)*MXFNT+1
NC=KFONT(KK)
KF=KFONT(KK+1)
IKF=IABS(MOD(KF,10))
IF (IKF.NE.MFOLD) (
NAMFNT(3)=NUMBR(IKF)
CALL CFONT (KCCB,NAMFNT,NSEC,NCR,KDCB)
)
IF (KF.LT.0) (
CALL CSIZE (KCCB,CHITE+SUP,ASPEC,SLANT,0)
CALL WHERE (KCCB,XP,YP)
IF (IABS(KF).LT.10) CALL MOVE (KCCB,XP+XOFF,YP+YOFF)
ELSE CALL MOVE (KCCB,XP-XOFF,YP-YOFF)
)
CALL GTEXT (KCCB,LABL,NS,NC,KDCB)
IF (KF.LT.0) (
CALL CSIZE (KCCB,CHITE,ASPEC,SLANT,0)
CALL WHERE (KCCB,XP,YP)
IF (IABS(KF).LT.10) CALL MOVE (KCCB,XP-XOFF,YP-YOFF)
ELSE CALL MOVE (KCCB,XP+XOFF,YP+YOFF)
)
NS=NS+NC
MFOLD=IKF
)
CALL CFONT (KCCB,0.0.0.KDCB)
RETURN
END
```

File: &LOCKY

```
*CALL TDEFM
*IF HP1000
EMA (XYZ,0)
*ENDIF
      INTEGER FUNCTION LOCK (X)
      GET X-LOCATION INDEX
      *CALL TENA
      *CALL TCOMM
      LOCK=1
      XP=XPOS(LOCK)
      WHILE ((X.GT.XP).AND.(LOCK.LT.MXMAX)) [
        LOCK=LOCK+1
        XP=XPOS(LOCK)
      ]
      IF ((LOCK.NE.1).AND.(X.LT.XP)) LOCK=LOCK-1
      *.....
      DONE
      RETURN
      END
```

File: &LOCKY

```
*IF HP1000
EMA (XYZ,0)
*ENDIF
      INTEGER FUNCTION LOCY (Y)
      GET Y-LOCATION INDEX
      *CALL TENA
      *CALL TCOMM
      LOCY=1
      YP=YPOS(LOCY)
      WHILE ((Y.GT.YP).AND.(LOCY.LT.MYMAX)) [
        LOCY=LOCY+1
        YP=YPOS(LOCY)
      ]
      IF ((LOCY.NE.1).AND.(Y.LT.YP)) LOCY=LOCY-1
      *.....
      DONE
      RETURN
      END
```



```

*CALL TDEFN
*IF HP1000
EM(XYZ,0)
*ENDIF
SUBROUTINE OUTGP (KGRPH,KDISP,KSIGN,KFELD)
  GET GRAPHICS OUTPUT INFO'S
  KDISP = OUTPUT FLAG
  0 -> SAVE INPUT
  1 -> DOPING PROFILE
  2 -> CARRIER
  3 -> FIELD
  4 -> POTENTIAL
  KGRPH = GRAPHICS OUTPUT FLAG
  0 -> END OF OUTPUT
  1 -> 2-D
  2 -> 2-D, CARRIER DENSITY
  3 -> 3-D GRAPHICS DISPLAY: Z() = DATA
  4 -> CONTOUR PLOT OF POTENTIAL
  KI = INDEX OF LAST WORD
  KF = INDEX OF LAST FONT
  KFONTX(1,K) = # OF CHARACTERS IN FONT KFONTX(2,K)
  KFONTY(1,K) = # OF CHARACTERS IN FONT KFONTY(2,K)
  KFONTZ(1,K) = # OF CHARACTERS IN FONT KFONTZ(2,K)
  2-D PLOT:
  (NX1,NX2) INDEX OF POSITION ARRAY Z(N,1)
  (NY1,NY2) SET TO NAME OF CROSS SECTION, I.E. "X" OR "Y"
  (X1,X2) SET TO THE COMPLEMENT OF CROSS SECTION NAME
  (Y1,Y2) POSITION ARRAY LIMITS
  (Z1,Z2) CROSS SECTION POSITION (SET TO EQUAL)
  (Z1,Z2) FUNCTION LIMITS
  3-D PLOT:
  (NX1,NX2) INDEX OF X LIMITS
  (NY1,NY2) INDEX OF Y LIMITS
  (X1,X2) X LIMITS
  (Y1,Y2) Y LIMITS
  (Z1,Z2) Z LIMITS
*CALL TEMA
*CALL TCONNO
  DIMENSION LBUF(40)
  DATA NANY/ZNY /, NANY/ZNY /, NANY/ZNY /, NANY/ZNY /,
  DATA KSTICK/2/, KR0HAN/3/, KNATH/5/, HFONT/10/, LUPLTR/9/
  DATA HUR/4/
  WRITE (KONSOL,6010)
  READ (KEYBRD,2000) KANSUR
  *IF BATCH
  WRITE (KONSOL,2000) KANSUR
*ENDIF
6010 FORMAT("Log scale? (Yes=f7/No=f8) _")
  IF (KANSUR.EB.KYES) [
    KLOG=1
    IF (Z1.NE.0.0<EXP>0) Z1=ALOGT(ABS(Z1))
    IF (Z2.NE.0.0<EXP>0) Z2=ALOGT(ABS(Z2))
    IF (Z1.GE.Z2) [ T=Z1; Z1=Z2; Z2=T ]
  ]
  ELSE KLOG=0
  IF (ABS(KGRPH).EQ.2) [
    WRITE (KONSOL,6015)
    READ (KEYBRD,2000) KANSUR
  ]
*IF BATCH
  WRITE (KONSOL,6015) KANSUR
*ENDIF
6015 FORMAT("Relative position (Yes=f7/No=f8) ? _")
  IF (KANSUR.EB.KYES) [
    KRELC=1
    DOMAIN=1.0<EXP>0/(Z(NX2,1)-Z(NX1,1))
    NSTART=NX1+1
    NSTOP=NX2-1
    DO N=NSTART, NSTOP; Z(N,1)=(Z(N,1)-Z(NX1,1))*DOMAIN
    Z(NX1,1)=0.0<EXP>0
    Z(NX2,1)=1.0<EXP>0
    NI=0.0<EXP>0
  ]

```

```

  XZ=1.0<EXP>0
  ]
  ELSE KRELC=0
  ]
  ELSE KRELC=0
  WRITE (KONSOL,6000)
  READ (KEYBRD,2000) KANSUR
  *IF BATCH
  WRITE (KONSOL,2000) KANSUR
*ENDIF
2000 FORMAT(A1)
6000 FORMAT("On the console (Yes=f7/No=f8) ? _")
  IF (KANSUR.EB.KYES) LU=KONSOL
  ELSE LU=LUPLTR
  IF (KGRPH.EQ.3) [
    WRITE (KONSOL,6020) NMX
    READ (KEYBRD,0) NX
  ]
*IF BATCH
  WRITE (KONSOL,6021) NX
  FORMAT(I3)
*ENDIF
6021
*ENDIF
  WRITE (KONSOL,6020) NMY
  READ (KEYBRD,0) NY
*IF BATCH
  WRITE (KONSOL,6021) NY
*ENDIF
6020
  FORMAT("How many points in ",A1,"-direction ? _")
  WRITE (KONSOL,6030)
  READ (KEYBRD,0) TILT
*IF BATCH
  WRITE (KONSOL,6031) TILT
  FORMAT(IP10.3)
*ENDIF
6031
*ENDIF
6030
  FORMAT("Tilt angle (degree) ? _")
  WRITE (KONSOL,6040)
  READ (KEYBRD,0) ROTAT
*IF BATCH
  WRITE (KONSOL,6031) ROTAT
*ENDIF
6040
  FORMAT("Rotation angle (degree) ? _")
  IF (KLOG.EQ.1) DO K=NX1,NX2; DO KY=NY1,NY2 [
    ZZ=ABS(Z(KX,KY))
    IF (ZZ.NE.0.0<EXP>0) Z(KX,KY)=ALOGT(ZZ)
  ]
  ELSE IF (KLOG.EQ.1) DO K=NX1,NX2 [
    ZZ=ABS(Z(K,2))
    IF (ZZ.NE.0.0<EXP>0) Z(K,2)=ALOGT(ZZ)
  ]
  ]
  PREPARE LABELS
  IF (KLOG.EB.0) [
    LUNTZ=LUNIT(Z1,Z2)
    IF (LUNTZ.NE.1) [
      ZUNIT=10.0<EXP>0**(-LUNTZ)
      Z1=Z1*ZUNIT
      Z2=Z2*ZUNIT
      IF (KGRPH.NE.3) DO K=NX1,NX2; Z(K,2)=Z(K,2)*ZUNIT
      ELSE DO K=NX1,NX2; DO KY=NY1,NY2; Z(KX,KY)=Z(KX,KY)*ZUNIT
      ITEM=0
      IT=LUNTZ
      IF (IT.LT.0) ITEM=ITEM+1
      WHILE (IT.NE.0) [ ITEM=ITEM+1; IT=IT/10 ]
    ]
  ]
  ELSE ITEM=0
  ]
  ELSE ITEM=0
  KL=0
  KF=1
  KFONTZ(1,1)=0
  KFONTZ(2,1)=KR0HAN
  IF (KDISP.EQ.1) [
    CALL CODE; WRITE (LBUF,7010)
    FORMAT ("Doping Conc. (")
    LAB=7
  ]
  IF (KDISP.EQ.2) [
    IF ((KSIGN.EQ.1).AND.(KGRPH.LT.0)) [
      CALL CODE; WRITE (LBUF,7021)
    ]
  ]

```



```

File: &OUTP1

READ (KEYBRD,*) MY1,MY2
MY1=MIN0(MYMAX,MAX0(1,MY1))
MY2=MIN0(MYMAX,MAX0(1,MY2))
IF (MY1.GT.MY2) ( NT=MY1; MY2=MY2; MY2=NT )

*IF BATCH
*ENDIF

WRITE (KONSOL,4041) MY1,MY2

DO K=MY1,MY2 (
Z(K,1)=Z(K,4)          0 LOAD DATA
Z(K,2)=OUTDA (KX,K,KDISP,KSIGN,KFELD)
)
NX1=MY1;          NX2=MY2  0 SET SPECIFICATIONS
NY1=MAXX;          NY2=MAXY
X1=Z(NX1,1);      X2=Z(NX2,1)
Y1=Z(KX,3);      Y2=Y1
)
WRITE (KONSOL,4050) (K,Z(K,2),K=NX1,NX2)
FORMAT ('00 N.Value 00,6X,4(1X,12,0,0,1PG10.3)^
/, (4X,5(1X,12,0,0,1PG10.3)))

WRITE (KONSOL,5020)
READ (KEYBRD,*) Z1,Z2          0 GET THE DATA RANGE

*IF BATCH
5021
*ENDIF
WRITE (KONSOL,5021) Z1,Z2
FORMAT(1P2G13.3)

IF (Z1.LT.Z2) KGRPH=2          0 SET GRAPHICS INDEX

0
0.....CASE OF NOT 2-D GRAPHICS
ELSE (
*IF IBATCH
*ENDIF
WRITE (KONSOL,4020) (NAMX,J=1,2),(K,Z(K,3),K=1,NXMAX)
WRITE (KONSOL,4040)          0 GET X-DOMAIN INDICES
READ (KEYBRD,*) NX1,NX2
NX1=MIN0(NXMAX,MAX0(1,NX1))
NX2=MIN0(NXMAX,MAX0(1,NX2))
IF (NX1.GT.NX2) ( NT=NX1; NX1=NX2; NX2=NT )
*IF BATCH
*ENDIF
*IF IBATCH
*ENDIF
WRITE (KONSOL,4041) NX1,NX2

WRITE (KONSOL,4020) (NAMY,J=1,2),(K,Z(K,4),K=1,MYMAX)
WRITE (KONSOL,4040)          0 GET Y-DOMAIN INDICES
READ (KEYBRD,*) MY1,MY2
MY1=MIN0(MYMAX,MAX0(1,MY1))
MY2=MIN0(MYMAX,MAX0(1,MY2))
IF (MY1.GT.MY2) ( NT=MY1; MY1=MY2; MY2=NT )
*IF BATCH
*ENDIF
*IF IBATCH
*ENDIF
WRITE (KONSOL,4041) NX1,NX2

NSEND=MIN0(NX1+6,NXMAX)      0 DEFINE CONSOLE DISP DOMAIN
NYEND=MIN0(MY1+7,MYMAX)
DO K=NX1,NSEND; XPRNT(K-NX1+1)=Z(K,3)
DO K=MY1,NYEND; YPRNT(K-MY1+1)=Z(K,4)
DO KX=NX1,NX2; DO KY=MY1,MY2  0 LOOP OF DATA LOADING
Z(KX,KY)=OUTDA (KX,KY,KDISP,KSIGN,KFELD)
WRITE (KONSOL,5010) (K,K=NX1,NXEND),(XPRNT(K),K=1,7),^
(KSTAR,K=1,40),(J,YPRNT(J-MY1+1),^
KSTAR,(Z(K,J),K=NX1,NXEND),J=MY1,NYEND)
FORMAT (5X,7I10,0 YX(un) 0,1PG9.2,6(1PG10.2))/,39A2,A1/,^
(12,OPF7.2,A1,1PG9.2,6(1PG10.2)))

*IF BATCH
*ENDIF
5020
*IF BATCH
*ENDIF
WRITE (KONSOL,5020)          0 GET DATA RANGE
FORMAT (/, 'Estimated MIN/MAX function values ',^
('MIN=)MAX ->skip) ? -')
READ (KEYBRD,*) Z1,Z2

*IF BATCH
*ENDIF
WRITE (KONSOL,5021) Z1,Z2

IF (Z1.LT.Z2) (
X1=XPOS(NX1);      X2=XPOS(NX2)  0 SET SPECIFICATIONS
Y1=YPOS(MY1);      Y2=YPOS(MY2)
IF (KTRGT.EQ.2) KGRPH=3          0 SET 3-D PLOT FLAG
IF (KTRGT.EQ.3)          0 SAVE IN DISC FILE
CALL SAVOU (NX1,NX2,MY1,MY2,X1,X2,Y1,Y2,Z1,Z2,^
KDISP,KSIGN,KFELD)
IF (KTRGT.EQ.4)          0 PRINT
)

```

```

File: &OUTP1

CALL JPRNT (NX1,NX2,MY1,MY2,X1,X2,Y1,Y2,Z1,Z2,^
KDISP,KSIGN,KFELD)

)
)
)
*IF GRAPHICS
IF ((KGRPH.EQ.0).AND.(KGRPH.EQ.4).AND.(KGRPH.EQ.99))
*ENDIF
CALL OUTCP (KGRPH,KDISP,KSIGN,KFELD)
IF (KGRPH.EQ.99) KFLAG=0
ELSE KFLAG=IABS(KGRPH)
0
0.....DONE
RETURN
END

```



```

*CALL TUDEFN
SUBROUTINE OUTP4 (KFLAG)
0
0 GRAPHICS DATA DISPLAY
0 KFLAG = 0 -> PLOT MESH
0 2 -> 2-D PLOT OF Z(N,1) VERSUS Z(N,2)
0 3 -> OPAGUE 3-D PLOT OF ARRAY Z( )
0 4 -> EQUAL POTENTIAL CONTOUR PLOT
0
*CALL TCONMO
0
0 DATA KYES/2MY /, LUPLTR/9/
0
0 WRITE (KONSOL,3000)
0 READ (KONSOL,2000) KANSUR
3000 FORMAT("On the console (Yes=f7/No=f8) _")
2000 FORMAT(A1)
IF (KANSUR.EQ.KYES) LU=KONSOL
ELSE LU=LUPLTR
WRITE (KONSOL,5020)
READ (KONSOL,*) VMIN,VMAX,NUMLIN
5020 FORMAT("Potential min, max and number of lines? _")
CALL PLOTZ (VMIN,VMAX,NUMLIN,LU)
RETURN
END

```

```

*CALL TUDEFN
SUBROUTINE OUTPS (KFLAG)
0
0 OUTPUT CONTROLLER
0
0 KFLAG = -1 -> PLOT MESH
0 0 -> SAVE INPUT
0 1 -> OUTPUT AFTER DOPING PROFILE GENERATED
0 4 -> POTENTIAL
0
0 KOUNT = COUNT OF OUTPUT LOOP
0
0 KGO = STATUS FLAG
0 = 0 -> END OF OUTPUT
0 = 1 -> CHECK WHICH OUTPUT AND GET OUTPUT DATA
0
*CALL TCONMO
0
0 DATA KYES/2MY /, KMSG/9/
0
0 IF GRAPHICS&HP1000
0 IF (KFLAG.EQ.-1) CALL LINK (1HE,0) 0.....PLOT MESH
*ENDIF
0 IF GRAPHICS&HP1000
0 IF (KFLAG.EQ.-1) CALL OUTP1 (0)
*ENDIF
0 IF HP1000&IBATCH
0 IF (KFLAG.EQ.0) CALL LINK (1HD,0.0) 0.....SAVE INPUT
*ENDIF
0 IF HP1000&BATCH
0 IF (KFLAG.EQ.0) CALL LINK (1H4,0.0)
*ENDIF
0 IF 1HP1000
0 IF (KFLAG.EQ.0) CALL OUTP1 (0,0)
*ENDIF
0 IF ((KFLAG.NE.0).AND.(KFLAG.NE.-1)) [
0 KOUNT=1
0 REPEAT [
0 KDISP=KFLAG
0 IF HP1000&IBATCH
0 CALL LINK (1HD,KOUNT,KDISP) 0.....GET OUTPUT DATA
*ENDIF
0 IF HP1000&BATCH
0 CALL LINK (1H4,KOUNT,KDISP)
*ENDIF
0 IF 1HP1000
0 CALL OUTP1(KOUNT,KDISP)
*ENDIF
0 IF GRAPHICS&HP1000
0 IF (KDISP.NE.0) [
0 IF (KDISP.EQ.2) CALL LINK (1HE,KDISP) 0 2-D PLOT
0 IF (KDISP.EQ.3) CALL LINK (1HF,KDISP) 0 3-D PLOT
0 IF (KDISP.EQ.4) CALL LINK (1HG,KDISP) 0 CONTOUR PLOT
0 ]
*ENDIF
0 IF GRAPHICS&HP1000
0 IF (KDISP.NE.0) [
0 IF (KDISP.EQ.2) CALL OUTP2 (KDISP)
0 IF (KDISP.EQ.3) CALL OUTP3 (KDISP)
0 IF (KDISP.EQ.4) CALL OUTP4 (KDISP)
0 ]
*ENDIF
0 KOUNT=KOUNT+1
0 IF HP1000&IBATCH
0 CALL LINK (1HD,KANSUR,-KMSG) 0 CHECK IF ANOTHER DISPLAY
*ENDIF
0 IF HP1000&BATCH
0 CALL LINK (1H4,KANSUR,-KMSG)
*ENDIF
0 IF 1HP1000
0 CALL OUTP1 (KANSUR,-KMSG)
*ENDIF
0 IF
0 IF (KANSUR.EQ.KYES) KGO=1
0 ELSE KGO=0
0 ] UNTIL (KGO.EQ.0)
0 ]
0 RETURN
0 END

```



```

*CALL TDEFN
SUBROUTINE PAPER (IGCB,XONY,KONSOL)
0
0 CHECK PAPER SIZE FOR THE PLOTTING ON HP9872
0
0 DIMENSION IGCB(192)
0
0 DATA KYES/2NY /
DATA XLEFT/ 25.0(EXP)0/,XRITE0/190.0(EXP)0/,,^
YLOWR0/ 10.0(EXP)0/,YUPPR0/260.0(EXP)0/,,^
XFULL0/215.9(EXP)0/,XHALF0/100.0(EXP)0/,,^
YFULL0/275.4(EXP)0/,YHALF0/139.7(EXP)0/,,^
EDGE / 15.0(EXP)0/
0
0 275 mm = 11. inch, 215 mm = 8.5 inch
25 mm = 2.5 cm, 190 mm = 8.5 inch - 1 cm
10 mm = 1.0 cm, 260 mm = 11. inch - 1 cm
0
0 Thesis format : Horizontal -> Top margin = 1.5", Bottom margin = 1.0"
Left 1.0", Right = 1.0"
0
0.....CASE OF STANDARD SIZE 11X8.5
WRITE (KONSOL,1000)
1000 FORMAT("Is it a 11"x8.5" paper (Yes=f7/No=f8) ? _")
READ (KONSOL,2000) KANSUR
2000 FORMAT(A1)
IF (KANSUR.EQ.KYES) [
WRITE (KONSOL,1020)
1020 FORMAT("Is it vertical (Yes=f7/No=f8) ? _")
READ (KONSOL,2000) KORNT
WRITE (KONSOL,1030)
1030 FORMAT("1 or 2 figure(s) on the paper ? _")
READ (KONSOL,0) KNUNBR
KNUNBR=MIN0(2,MAX0(1,KNUNBR))
IF (KORNT.EQ.KYES) [
IF (KNUNBR.EQ.2) [
LEFT=EDGE
XLEFT=XFULL0-EDGE
WRITE (KONSOL,1040)
1040 FORMAT("On the upper part of the paper (Yes=f7/No=f8) ? _")
READ (KONSOL,2000) KANSUR
IF (KANSUR.EQ.KYES) [
YLOWR=YHALF0-EDGE+0.5(EXP)0
YUPPR=YFULL0-EDGE-EDGE
]
ELSE [
YLOWR=EDGE+EDGE
YUPPR=YHALF0+EDGE+0.5(EXP)0
]
]
]
ELSE [
XLEFT=0.0(EXP)0
XRITE=XFULL0-EDGE
YLOWR=EDGE+EDGE
YUPPR=YFULL0
]
]
]
ELSE [
IF (KNUNBR.EQ.2) [
YLOWR=XLEFT0
YUPPR=XRITE0
WRITE (KONSOL,1050)
1050 FORMAT("On the left part of the paper (Yes=f7/No=f8) ? _")
READ (KONSOL,2000) KANSUR
IF (KANSUR.EQ.KYES) [
XLEFT=0.0(EXP)0
XRITE=YHALF0
]
ELSE [
XLEFT=YHALF0-EDGE-EDGE
XRITE=YFULL0-EDGE-EDGE
]
]
]
ELSE [
XLEFT=YLOWR0
XRITE=YUPPR0
YLOWR=XLEFT0-EDGE+0.5(EXP)0
YUPPR=XRITE0-EDGE+0.5(EXP)0
]
]
]

```

```

] CALL LIMIT(IGCB,XLEFT,XRITE,YLOWR,YUPPR)
XONY=(XRITE-XLEFT)/(YUPPR-YLOWR)
]
0.....CASE OF NON-STANDARD PAPER SIZE
ELSE [
WRITE (KONSOL,1010)
CALL PEN(IGCB,4)
CALL LIMIT(IGCB)
CALL PEN(IGCB,0)
WRITE (KONSOL,9000)
READ (KONSOL,0) XONY
]
1010 FORMAT ("When 'ENTER' key is lit, do the following!"
//. (1) Move pen to lower left corner of paper^^
//. (2) Mark position for future alignment^^
//. by pressing PEN-DOWN followed by PEN-UP^^
//. (or align with previous mark on paper)^^
//. (3) Press the ENTER key^^
//. (4) Move pen to upper right corner^^
//. (5) Mark or align as in step (2)^^
//. (6) Press the ENTER key")
9000 FORMAT("X/Y plot ratio (suggest 1.4 if horizontal, else 0.7) ? _")
]
0.....DONE
RETURN
END

```


File: &PHMIN

```

*CALL TUNDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE PHMIN (M,PHIN,LMIN)
*
LOCATE POTENTIAL MINIMUM
*
*CALL TEMA
*CALL TCOMMH
*
TMOV1=VT300K+VT300K
LMIN=NSOURC
PHIN=POTS1(LMIN,M)
M1=NSOURC+1
DO N=M1,NDRAIN [
POTM=POTS1(N,M)
IF (POTM.LT.PHIN) [ LMIN=M] PHIN=POTM ]
]
RETURN
END
```

-75-

File: &PLU12

```

*CALL TUNDEFN
*
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE PLOT2 (X1,X2,Y1,Y2,M1,M2,LABLX,LABLY,LABLZ,
KFONTX,KFONTY,KFONTZ,KLOG,LU,KONSOL)
*
2-DIMENSIONAL PLOT
*
DATA: X=Z(N,1), Y=Z(N,2) -> M=M1,M2
FONT: KFONTX(2,10),KFONTY(2,10) -> UP TO 10 CHANGES
LABEL: LABLX(40), LABLY(40), LABLZ(40) -> UP TO 80 CH (INCLUDING CTL CH)
*CALL TEMA
*
*.....PLOTTING PARAMETERS
DIMENSION KCCB(192),KDCB(144),LABLX(1),LABLY(1),LABLZ(1),
KFONTX(2,11),KFONTY(2,10),KFONTZ(2,10)
*
DATA LUPLTR/9/, ISPEED/2/, KESC/033B/, KBELL/7/, KYES/2HY /
*
*.....LOOP OF PLOTTING
REPEAT [
IF (LU.NE.LUPLTR) [
KTYPE=1; CALL PLOT2(KCCB,KTYPE,1,LU) * SET UP THE KONSOL
XONY=2.0(EXP)0
WRITE (KONSOL,3000) KESC
FORMAT(2R1,"*dF-")
3000 ]
ELSE [
KTYPE=2; CALL PLOT2(KCCB,KTYPE,1,LU) * SET UP THE PLOTTER
CALL PAPER (KCCB,XONY,KONSOL)
WRITE (KONSOL,4000)
READ (KONSOL,0) KOLOR
FORMAT (*Which color? (1-4, as set up on the plotter) *)
4000 KOLOR=M1NO(4,MAXI(KOLOR,1))
CALL PEN (KCCB,KOLOR)
CALL XMT (KCCB)
WRITE (LU,4010) ISPEED
4010 FORMAT("S",11,"JVA1")
]
CALL ASCAL (KCCB,XONY,X1,X2,Y1,Y2) * SCALE SURFACE
CALL LINE (KCCB,0) * SOLID LINE
CALL MOVE (KCCB,X1,Y1) * DRAW THE FRAME
CALL DRAW (KCCB,X1,Y2)
CALL DRAW (KCCB,X2,Y2)
CALL DRAW (KCCB,X2,Y1)
CALL DRAW (KCCB,X1,Y1)
YP=AMINI(Y2,AMAXI(Y1,(Z(M1,2)))) * DRAW THE CURVE
CALL MOVE (KCCB,X1,YP)
NS=M1+1
DO N=M1,M2 [
MP=AMINI(X2,AMAXI(X1,(Z(N,1))))
YP=AMINI(Y2,AMAXI(Y1,(Z(N,2))))
CALL DRAW (KCCB,MP,YP)
]
CALL PENUP (KCCB)
*
*.....CHECK IF ADD LABELS
WRITE (KONSOL,4050) KBELL,KESC
READ (KONSOL,3000) KANSUR
4050 FORMAT(2R1,"*dEadd labels (Yes=f7/No=f8) *-")
IF (KANSUR.EQ.KYES) [
IF (LU.EQ.KONSOL) WRITE (KONSOL,3000) KESC
IF (KLOG.EQ.0) CALL AXLIN (KCCB,KDCB,XONY,X1,X2,Y1,Y2)
ELSE CALL AXLOC (KCCB,KDCB,XONY,X1,X2,Y1,Y2)
CALL AXLAB (KCCB,KDCB,XONY,X1,X2,Y1,Y2,LABLX,LABLZ,KFONTX,KFONTZ)
5000 WRITE (KONSOL,3000) KBELL,KESC
FORMAT(2R1,"*dE-")
]
*
*.....FINISH THE PLOT
IF (LU.EQ.LUPLTR) CALL PEN (KCCB,0)
CALL PLOT2 (KCCB,KTYPE,0)
*
*.....CHECK IF DUMP TO PLOTTER
KGO=0
IF (LU.NE.LUPLTR) [
```

143

-76-

File: &PLOT2

```
        WRITE (KONSOL,6000)
        READ  (KONSOL,2000) KANSUR
        IF (KANSUR.EQ.KYES) I KGO=1; LU=LUPLTR ;
    )
    ) UNTIL (KGO.EQ.0)
6000  FORMAT("Replot on the plotter (Yes=f7/No=f8) ? _")
2000  FORMAT(A1)
    )
    ) ..... DONE
    RETURN
    END
```

File: &PLOT3

```
*CALL TUDEFN
*IF HP1000
EHA(XYZ,0)
*ENDIF
SUBROUTINE PLOT3 (X1,X2,Y1,Y2,Z1,Z2,NX,NY,ROTAT,TILT,LU,KONSOL)
    )
    ) CALL TEMA
    ) ..... PLOTTING PARAMETERS
    DIMENSION KCCB(192)
    DATA LUPLTR/9/, ISPEED/2/, KESC/0338/, KBELL/7/, KYES/2HY /
    )
    ) ***** INITIALIZATION *****
    )
    CALL ANGLE (ROTAT,KOR); CALL ANGLE (TILT ,KAT)
    COSR=COS(ROTAT); COST=COS(TILT)
    SINR=SIN(ROTAT); SINT=SIN(TILT)
    )
    XSPAN=X2-X1 ZSPAN=Z2-Z1
    YSPAN=Y2-Y1 XOVRY=XSPAN/YSPAN; XOVZ=XSPAN/ZSPAN
    )
    DXPDY= SINR; DXPDY=COSR*XOVRY
    DYPDX=-COSR*SINT; DYPDY=SINR*SINT+XOVRY; DYPDZ=COST*XOVZ
    )
    XPX1=X1+DXPDY; XPX2=X2+DXPDY
    XPY1=Y1+DYPDX; XPY2=Y2+DYPDX
    YPX1=X1+DYPDX; YPX2=X2+DYPDX
    YPY1=Y1+DYPDY; YPY2=Y2+DYPDY
    )
    XP11=XPX1+XPY1; XP12=XPX1+XPY2
    XP21=XPX2+XPY1; XP22=XPX2+XPY2
    YP11=YPX1+YPY1; YP12=YPX1+YPY2
    YP21=YPX2+YPY1; YP22=YPX2+YPY2
    )
    YPZ1=Z1+DYPDZ; YPZ2=Z2+DYPDZ
    )
    XLINO=ANIN1(XP11,XP12,XP21,XP22)
    XLINI=ANAX1(XP11,XP12,XP21,XP22)
    YLINO=ANIN1(YP11,YP12,YP21,YP22)+YPZ1
    YLINI=ANAX1(YP11,YP12,YP21,YP22)+YPZ2
    )
    DX=XSPAN/(NX-1); DY=YSPAN/(NY-1)
    DXPX=DX+DXPDY; DXPY=DY+DYPDY
    DYPX=DX+DYPDX; DYPY=DY+DYPDY
    )
    ) ..... INITIALIZE THE DEVICE
    REPEAT (
    IF (LU.NE.LUPLTR) (
    KTYPE=1; CALL PLOTR(KCCB ,KTYPE,1,LU)
    XOMY=2.0*(EXP)0
    WRITE (KONSOL,3000) KESC
3000  FORMAT(R1,"*JF_")
    )
    ELSE (
    KTYPE=2; CALL PLOTR (KCCB,KTYPE,1,LU)
    CALL PAPER (KCCB,XOMY,KONSOL)
    WRITE (KONSOL,4000)
    READ (KONSOL,*) KOLOR
    FORMAT ("Which color? (1-4, as set up on the plotter) _")
4000  KOLOR=MIN0(4,MAX0(KOLOR,1))
    CALL PEN (KCCB,KOLOR)
    CALL XMIT (KCCB)
    WRITE (LU,4010) ISPEED
4010  FORMAT("VS",I1,"VAI")
    )
    ) CALL LINE (KCCB,0)
    ) ..... SCALE THE PLOTTING PLANE
    CALL ASCAL (KCCB,XOMY,XLINO,XLINI,YLINO,YLINI)
    )
    ) ***** PLOTTING SECTION *****
    )
    ) ..... DRAW Y-LINES
    KD=0
    X=X1-DX
    XPLOT=XP11-DXPX
    YPLOT=YP11-DYPX
    DO KX=1,NX (
```


File: &PLOTG

```
*CALL TUDFN
*IF NP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE PLOTG (VMIN,VMAX,MUNLIN,LU)
*
* CONTOUR PLOT
* Z(50,40) = LINE SEARCHING STATUS
* STORED BY SUBROUTINE LNMAR
* LOADED BY INTEGER FUNCTION LNCBK
*
*CALL TEMA
*CALL TCOHMM
*
* DIMENSION VLINE(20)
*
* ..... PLOTTING PARAMETERS
* DIMENSION KGC(192), KDCB(144), LBUF(25)
* DATA LUPLTR/9/, ISPEED/2/, KESC/0330/, KBELL/77/, KYES/2HY /
* DATA UM/1.0(EMP)4/, CHARN/25.0(EMP)0/
* DATA MSEC/0/, MCR/2HGS/, ARTIO/0.55(EMP)0/
* DATA MANK/2MX /, MARY/2HY /, MARG/2HGS/, MANDV/2Hds/, MARYB/2Hds/
*
* DATA MMAX/15/
*
* 2000 FORMAT (A1)
*
* ..... DETERMINE POTENTIAL VALUES
* MUNLIN=MIN(MMAX,MAX(2,MUNLIN))
* VLINE(1)=VMIN
* DVAL=(VMAX-VMIN)/(MUNLIN-1)
* DO K=2,MUNLIN VLINE(K)=VLINE(K-1)+DVAL
* WRITE (KONSOL,1000) (VLINE(K),K-1,MUNLIN)
* 1000 FORMAT ("=Line value(K)"/(3X,10F7.4))
*
* ..... INITIALIZE THE PLOTTING DEVICE
* REPEAT (
* IF (LU.NE.LUPLTR) [
* KTYPE=1) CALL PLOTG(KGC,KTYPE,1,LU)
* XOMY=2.0(EMP)0
* WRITE (KONSOL,3000) KESC
* 3000 FORMAT(RI,"=DF_")
* ]
* ELSE [
* KTYPE=2) CALL PLOTG(KGC,KTYPE,1,LU)
* CALL PAPER (KGC,XOMY,KONSOL)
* WRITE (KONSOL,4000)
* READ (KONSOL,*) KOLOR
* 4000 FORMAT("Which color? (1-4, as set up on the plotter) _")
* KOLOR=MIN(4,MAX(KOLOR,1))
* CALL PEN (KGC,KOLOR)
* CALL KRIT (KGC)
* 4010 WRITE (LU,4010) ISPEED
* FORMAT("VS",11,"VA")
* ]
* ]
*
* ..... OUTLINE DEVICE, SCALE AS (XPOS(1),XPOS(MMAX),-YMAX,TOX)
* AND SET TEXT SIZE AND QUALITY
* CALL PLOTG (KGC,XOMY)
* CALL TBCAL (KGC,XOMY,CHARN,CHITE,KLENG,VLENG)
* CALL LINE (KGC,0)
*
* ..... INITIALIZE INDEX ARRAY
* NI=MMAX-1
* NI=MYMAX-1
* DO L=1,MUNLIN) CALL LNMAR (0,0,0)
*
* ..... LOOP THROUGH ALL MESHES
* DO M=1,NI [
* POT1=POTS(M,1)
* DO N=1,NI [
* POT0=POT1
* POT1=POTS(M,N+1)
* POT2=POTS(M+1,N)
* ]
* ]
*
* ..... LOOP THROUGH ALL LINES
* DO L=MUNLIN,1,-1 [
* POTL=VLINE(L)
* SIGN0=SIGN(1.0(EMP)0,POTL-POT0)
*
```

File: &PLOTG

```
* ..... CHECK IF PASSING THROUGH THE NEXT Y-MESH
* IF (LNCBK(M,M,L).EQ.0) [
* SIGN1=SIGN(1.0(EMP)0,POTL-POT1)
* IF ((POTL.EQ.POT0).OR.(SIGN0.NE.SIGN1))
* CALL TRACE (KGC,KDCB,M,M,-L,POTL)
* ]
*
* ..... CHECK IF PASSING THROUGH THE NEXT X-MESH
* IF (LNCBK(M,M,-L).EQ.0).AND.(POTL.NE.POT0) [
* SIGN2=SIGN(1.0(EMP)0,POTL-POT2)
* IF (SIGN0.NE.SIGN2)
* CALL TRACE (KGC,KDCB,M,M,-L,POTL)
* ]
* ]
* ]
*
* ..... LABELING
* IF (LU.EQ.KONSOL) WRITE (KONSOL,6000) KBELL,KESC
* WRITE (KONSOL,5000)
* 5000 READ (KONSOL,2000) KANSUR
* FORMAT("Add labels (Yes=F7/No=FB) ? _")
* IF (KANSUR.EQ.KYES) [
* IF (LU.EQ.KONSOL) WRITE (KONSOL,3000) KESC
* ]
*
* ..... DRAW UPPER BRACKET
* TOX=MAX1(TOX1,TOX0)
* CHITX=CHITE+(TOX-YMAX)/YLENG
* CHITX=CHITX+(XMAX-XSOURC)/(YMAX*XOMY)
* CHYON2=CHITX*0.5(EMP)0
* CHXON2=CHITX*0.5(EMP)0
* YU0=TOX+CHYON2
* YU1=YU0+CHITX
* XU0=XPOS(MSOURC+1)
* XU1=XPOS(MDRAIN-1)
* CALL LINE (KGC,1)
* CALL MOVE (KGC,0.0(EMP)0,YU0)
* CALL DRAW (KGC,0.0(EMP)0,YU1)
* XP=XU0
* DX=XU0*0.1(EMP)0
* DO K=1,10 [ XP=XP+DX) CALL DRAW (KGC,XP,YU1) ]
* CALL DRAW (KGC,XU0,YU0)
* CALL MOVE (KGC,XU0,YU1)
* XP=XU0
* DX=(XU1-XU0)*0.1(EMP)0
* DO K=1,10 [ XP=XP+DX) CALL DRAW (KGC,XP,YU1) ]
* CALL DRAW (KGC,XU1,YU0)
* CALL MOVE (KGC,XU1,YU1)
* XP=XU1
* DX=(XCHAML-XU1)*0.1(EMP)0
* DO K=1,10 [ XP=XP+DX) CALL DRAW (KGC,XP,YU1) ]
* CALL DRAW (KGC,XCHAML,YU0)
*
* ..... TOP LABEL
* ZPART1=XCHAML*UH
* ZPART2=(XPOS(MDRAIN)-XPOS(MSOURC))*UH
* 5010 CALL CODE) WRITE (LBUF,5010) ZPART1,ZPART2
* FORMAT ("Drawn L =",F5.2," _m_n, Effective L =",F5.2," _m_n")
*
* ..... GET TEXT LENGTH
* CALL LDIR (KGC,0.0(EMP)0)
* TXYLEN=0.0(EMP)0
* CALL GFONT (KGC,6NFONT2 ,MSEC,MCR,KDCB)
* NS=1
* NC=16
* CALL GLEN (KGC,LBUF,NS,NC,XT,YT,KDCB)
* TXYLEN=TXYLEN+XT
* CALL GFONT (KGC,6NFONTS ,MSEC,MCR,KDCB)
* NS=17
* NC=2
* CALL GLEN (KGC,LBUF,NS,NC,XT,YT,KDCB)
* TXYLEN=TXYLEN+XT
* CALL GFONT (KGC,6NFONT2 ,MSEC,MCR,KDCB)
* NS=19
* NC=23
* CALL GLEN (KGC,LBUF,NS,NC,XT,YT,KDCB)
* TXYLEN=TXYLEN+XT
* CALL GFONT (KGC,6NFONTS ,MSEC,MCR,KDCB)
* NS=44
* NC=2
*
```

```

YP=0.0<EXP>0
DY=-YMAX*0.1<EXP>0
DO K=1,10 [ YP=YP+DY; CALL DRAW (KCCB,XL1,YP) ]
CALL DRAW (KCCB,XL0,-YMAX)
0
0.....LEFT LABEL
ZPRT=YMAX*UM
CALL CODE; WRITE (LBUF,5020) NAMY,ZPRT
0
0.....MOVE TO THE LOWEST POINT
XLZ=XL1-CXN2
CALL MOVE (KCCB,XLZ,-YMAX)
0
0.....IN SIMPLEX ROMAN
PIOM2=2.0<EXP>0*ATAN2(1.0<EXP>0,1.0<EXP>0)
CALL LDIR (KCCB,PIOM2)
CALL LINE (KCCB,0)
NS=1
NC=15
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT5 ,NSEC,NCR,KDCB)
NS=16
NC=2
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=18
NC=1
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
0
0.....POINT TO OXIDE
CALL LINE (KCCB,1)
XL3=XLZ-CHITX
IF (XONY.GT.1.0<EXP>0) YL3=-YMAX*0.1<EXP>0
ELSE YL3=-YMAX*0.3<EXP>0
CALL MOVE (KCCB,XL0,TOX)
CALL DRAW (KCCB,XL3,TOX)
YP=TOX
DY=(YL3-TOX)*0.1<EXP>0
DO K=1,10 [ YP=YP+DY; CALL DRAW (KCCB,XL3,YP) ]
0
0.....OXIDE LABEL
ZPRT1=TOX*UM
ZPRT2=TOX1*UM
CALL CODE; WRITE (LBUF,5035) ZPRT1,ZPRT2
FORMAT ('Oxide thickness = ',F5.3,' ',F5.3,' _a_n")
5035
0
0.....MOVE TO THE LOWEST POINT
XL4=XL3-CXN2
CALL MOVE (KCCB,XL4,-YMAX)
0
0.....IN SIMPLEX ROMAN
CALL LINE (KCCB,0)
NS=1
NC=34
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT5 ,NSEC,NCR,KDCB)
NS=35
NC=2
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=37
NC=1
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
0
0.....POSITION RIGHT LABELS
XRO=XCHAML+XDRAIN+CXN2
YRO=0.3<EXP>0*(-YMAX)
DYR=YRO*0.25<EXP>0
YRO=YRO+DYR
CALL LDIR (KCCB,0.0<EXP>0)
CALL MOVE (KCCB,XRO,YRO)
0
0.....LABEL VGS
VGS=VDB-VSB
VCS=VGB-VSS
VSD=-VSB
CALL CODE; WRITE (LBUF,5030) NANY,VGS
FORMAT ('V',A2,' = ',F6.2,' V')
IF (XONY.GT.1.0<EXP>0) [
NS=1

```

```

CALL GLEN (KCCB,LBUF,NS,NC,XT,YT,KDCB)
TXTLEN=XTLEN*XT
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=46
NC=1
CALL GLEN (KCCB,LBUF,NS,NC,XT,YT,KDCB)
TXTLEN=XTLEN*XT
0
0.....MOVE TO THE LEFT MOST POSITION
XUZ=(XCHAML-TXTLEN)*0.5<EXP>0
YUZ=YUI+CHYON2
CALL MOVE (KCCB,XUZ,YUZ)
0
0.....WRITE IN SIMPLEX ROMAN
CALL LINE (KCCB,0)
CALL LDIR (KCCB,0.0<EXP>0)
CALL LOG (KCCB,1)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=1
NC=16
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT5 ,NSEC,NCR,KDCB)
NS=17
NC=2
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=19
NC=25
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT5 ,NSEC,NCR,KDCB)
NS=44
NC=2
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=46
NC=1
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
0
0.....BOTTOM BRACKET
XDO=-NSOURC
XDI=XCHAML+XDRAIN
YDO=-YMAX-CHYON2
YDI=YDO-CHITY
CALL LINE (KCCB,1)
CALL MOVE (KCCB,XDO,YDO)
CALL DRAW (KCCB,XDO,YDI)
XP=XDO
DK=(XDI-XDO)*0.1<EXP>0
DO K=1,10 [ XP=XP+DK; CALL DRAW (KCCB,XP,YDI) ]
CALL DRAW (KCCB,XDI,YDO)
0
0.....BOTTOM LABEL
ZPRT=XMAX*UM
CALL CODE; WRITE (LBUF,5020) NAMY,ZPRT
FORMAT (A1,'-max = ',F5.2,' _a_n")
5020
0
0.....MOVE TO THE LEFT MOST POINT
YDZ=YDI-CHYON2-CHITY
CALL MOVE (KCCB,XDO,YDZ)
0
0.....IN SIMPLEX ROMAN
CALL LINE (KCCB,0)
NS=1
NC=15
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT5 ,NSEC,NCR,KDCB)
NS=16
NC=2
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KDCB)
NS=18
NC=1
CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
0
0.....LEFT BRACKET
XL0=XDO-CXN2*XONY
XLI=XL0-CHITX
CALL LINE (KCCB,1)
CALL MOVE (KCCB,XL0,0.0<EXP>0)
CALL DRAW (KCCB,XLI,0.0<EXP>0)

```


File: &PLOTG

```
      NC=14
      CALL GTEXT (KCCB,LBUF,NS,MC,KCCB)
    ]
    ELSE [
      NSA=1
      NCA=5
      CALL GTEXT (KCCB,LBUF,NSA,NCA,KCCB)
      NSV=6
      NCV=9
      CALL GTEXT (KCCB,LBUF,NSV,NCV,KCCB)
    ]
..... LABEL VDS
      YR0=YR0+DYR
      CALL MOVE (KCCB,XR0,YR0)
      CALL CODE; WRITE (LBUF,5030) NARVD,VDS
      IF (XONY.GT.1.0<EXP>0) CALL GTEXT (KCCB,LBUF,NS,MC,KCCB)
    ELSE [
      CALL GTEXT (KCCB,LBUF,NSA,NCA,KCCB)
      CALL GTEXT (KCCB,LBUF,NSV,NCV,KCCB)
    ]
..... LABEL VBS
      YR0=YR0+DYR
      CALL MOVE (KCCB,XR0,YR0)
      CALL CODE; WRITE (LBUF,5030) NARVD,VBS
      IF (XONY.GT.1.0<EXP>0) CALL GTEXT (KCCB,LBUF,NS,MC,KCCB)
    ELSE [
      CALL GTEXT (KCCB,LBUF,NSA,NCA,KCCB)
      CALL GTEXT (KCCB,LBUF,NSV,NCV,KCCB)
    ]
..... SUBSTRATE DOPING LABEL
      YR0=YR0+DYR
      CALL MOVE (KCCB,XR0,YR0)
      CALL CODE; WRITE (LBUF,5040) (IDEV(K),K=1,3)
      FORMAT("Nsub = ",J2)
      CALL GFONT (KCCB,6HFONT2 ,NSEC,NCR,KCCB)
      NS=1
      NC=13
      CALL GTEXT (KCCB,LBUF,NS,MC,KCCB)
..... CLOSE FONT FILE
      CALL GFONT (KCCB,0,0,0,KCCB)
    ]
..... FINISH UP
      CALL PENUP (KCCB)
      IF (LU.EQ.LUPLTR) CALL PEN (KCCB,0)
      CALL PLOTG (KCCB ,RTYPE,0)
..... RING THE BELL
      WRITE (KONSOL,6000) KBELL,KESC
      FORMAT(2R1,"de_")
..... CHECK IF DUMP TO PLOTTER
      KGO=0
      IF (LU.NE.LUPLTR) [
        WRITE (KONSOL,7000)
        READ (KONSOL,2000) KANSUR
        IF (KANSUR.EQ.KYES) [
          KGO=1
          LU=LUPLTR
        ]
      ]
    ] UNTIL (KGO.EB.0)
      7000 FORMAT("Replot on the plotter (Yes=f7/No=f8) ? _")
..... DONE
      RETURN
      END
```

-85-

File: &PLOTG

```
*IF MPI000
EMA (XYZ,0)
*ENDIF
      SUBROUTINE LMRK (M,H,L)
.....
      STORE LINE INDEX IN ARRAY Z(50,48)
      IF (M=0) RESET THE ARRAY
      ELSE [
        L>0 -> Y-DIRECTION; SET (L)TH BIT =1
        L<0 -> X-DIRECTION; SET (L+MLMAX)TH BIT =1
      ]
.....
*CALL TENA
*CALL TCOMM
.....
      DIMENSION KEY(2)
      EQUIVALENCE (KEY(1),BITS)
.....
      DATA MLMAX/15/
.....
      CHECK IF RESET
      IF ( (M.EQ.0).AND.(N.EQ.0).AND.(L.EQ.0) ) [
        DO KN=1,NHMAX; DO KM=1,NYRAX [ KEY(1)=0; KEY(2)=0; Z(KH,KH)=BITS ]
      ]
.....
      CHECK LINE INDEX
      ELSE [
        KK=IABS(L)-1
        IF ((KK.GE.0).AND.(KK.LT.MLMAX)) [
.....
          CHECK DIRECTION
          KDIR=1; IF (L.LT.0) KDIR=2
.....
          SET THE BIT
          NB=1; IF (KK.GT.0) DO K=1,KK; NB=NB+2
.....
          STORE THE BIT
          BITS=Z(M,H)
          KEY(KDIR)=KEY(KDIR)+NB
          Z(M,H)=BITS
        ]
      ]
.....
      DONE
      RETURN
      END
```

-86-

```

*IF HP1000
EMA (XYZ,0)
*ENDIF
      INTEGER FUNCTION LMCHK (N,N,L)
      LOAD LINE INDEX FROM ARRAY Z(50,48)
      IF L > 0 -> Y-DIRECTION, LOAD (L)TH BIT
      IF L < 0 -> X-DIRECTION, LOAD (L+MLMAX)TH BIT
      *CALL TEMA
      *CALL TCOMM
      DIMENSION KEY(2)
      EQUIVALENCE (KEY(1),BITS)
      DATA MLMAX/15/
      *.... CHECK LINE INDEX
      KK=ABS(L)-1
      IF ((KK.GE.0).AND.(KK.LT.MLMAX)) [
      *.... CHECK LINE DIRECTION
      KDIR=1] IF (L.LT.0) KDIR=2
      *.... LOAD THE FLAG
      BITS=Z(N,M)
      NB=KEY(KDIR)
      *.... GET THE BIT
      IF (KK.GT.0) DO K=1,KK; NB=NB/2
      LMCHK=MOD(NB,2)
      ]
      *.... DONE
      RETURN
      END

```

```

*CALL TMEFH
*IF HP1000
EMA (XYZ,0)
*ENDIF
      SUBROUTINE PLOTG (KCCB,NOMY)
      OUTLINE THE DEVICE
      *CALL TEMA
      *CALL TCOMM
      *.... PLOTTING PARAMETERS
      DIMENSION KCCB (1)
      *.... SCALE THE PLOTTING PLANE
      TOX=AMAXI(TOX0,TOX1)
      CALL LINE (KCCB,0)
      CALL ASCAL (KCCB,NOMY,-XSOURC,XMAX-XSOURC,-YMAX,TOX)
      *.... OUTLINE THE BOUNDARY AND THE INTERFACE
      REPS=EPS1/EP102
      X1=XSOURC
      X2=XMAX-XSOURC
      Y0=-YMAX
      Y1=REPS*(DELOX(1,1)+DELOX(1,2))
      Y2=REPS*(DELOX(NXMAX,1)+DELOX(NXMAX,2))
      CALL MOVE (KCCB,X1,Y1)
      CALL DRAW (KCCB,X1,Y0)
      CALL DRAW (KCCB,X2,Y0)
      CALL DRAW (KCCB,X2,Y2)
      IF ((TOX0.NE.0.<EXP>0).OR.(TOX1.NE.0.<EXP>0)) DO KX=NXMAX,1,-1 [
      X=XPOS(KX)
      Y=REPS*(DELOX(KX,1)+DELOX(KX,2))
      CALL DRAW (KCCB,X,Y)
      ]
      CALL MOVE (KCCB,X1,0.<EXP>0)
      CALL DRAW (KCCB,X2,0.<EXP>0)
      CALL PENUP(KCCB)
      *.... OUTLINE THE JUNCTIONS
      CALL LINE (KCCB,1)
      ND1=NDRAIN-1
      NS1=NSOURC+1
      DO N=NXMAX,ND1,-1 [
      NJ=0
      REPEAT [
      NJ=NJ+1
      TYPC=SIGN(1.0<EXP>0,(CONC(N,NJ)))
      ] UNTIL ((TYPC.EQ.TYPE).OR.(NJ.GE.NYMAX))
      NJ=XPOS(NJ)
      YJ=YPOS(NJ)
      CJ=CONC(N,NJ)
      IF (NJ.NE.1) YJ=YJ+DELY(NJ-1)*CJ/(CONC(N,NJ-1)-CJ)
      YJ=-YJ
      IF (N.EQ.NXMAX) CALL MOVE (KCCB,NJ,YJ)
      ELSE CALL DRAW (KCCB,NJ,YJ)
      ]
      DO N=NS1,1,-1 [
      NJ=0
      REPEAT [
      NJ=NJ+1
      TYPC=SIGN(1.0<EXP>0,(CONC(N,NJ)))
      ] UNTIL ((TYPC.EQ.TYPE).OR.(NJ.GE.NYMAX))
      NJ=XPOS(NJ)
      YJ=YPOS(NJ)
      CJ=CONC(N,NJ)
      IF (NJ.NE.1) YJ=YJ+DELY(NJ-1)*CJ/(CONC(N,NJ-1)-CJ)
      YJ=-YJ
      IF (N.EQ.NS1) CALL MOVE (KCCB,NJ,YJ)
      ELSE CALL DRAW (KCCB,NJ,YJ)
      ]
      CALL PENUP (KCCB)
      *.... DONE
      RETURN
      END

```

File: &PLOTM

```

*CALL TDEFM
*IF NP1000
EMA(XYZ,0)
*ENDIF
SUBROUTINE PLOTM
PLOT MESH
*CALL TEMA
*CALL YCOMM
PLOTING PARAMETERS
DIMENSION KCCB (192)
DATA LUPLTR/9/,KESC/0J3B/,KBELL/007B/,KYES/2HY /,ISPEED/2/,
KUPHOV/-2/,KDHNOV/-1/,KNOVUP/2/,KNOVDN/1/
***** INITIALIZATION *****
..... INITIALIZE DEVICE
KCO=1
LU=KONSOL
WHILE (KCO.EQ.1) [
IF (LU.NE.LUPLTR) [
KTYPE=1] CALL PLOTM(KCCB,KTYPE,1,LU)
XOMY=2.0*(EXP)0
WRITE (KONSOL,3000) KESC
FORMAT(R1,"dF-")
]
ELSE [
KTYPE=2] CALL PLOTM(KCCB,KTYPE,1,LU)
CALL PAPER(KCCB,XOMY,KONSOL)
WRITE (KONSOL,4000)
READ (KONSOL,*) KOLOR
FORMAT("Which color? (1-4, as set up on the plotter) _")
KOLOR=MIN(4,MAX(KOLOR,1))
CALL PEN (KCCB,KOLOR)
CALL MAT (KCCB)
WRITE (LU,4010) ISPEED
FORMAT("VS",11,"JVA")
]
]
..... SCALE PLOTTING PLANE AND OUTLINE DEVICE
CALL PLOTD (KCCB,XOMY)
CALL LINE (KCCB,0)
***** PLOTTING SECTION *****
TON=AMANI(TOXO,TOXI)
..... DRAW Y-LINES
REPS=EPSI/EPSI02
Y2=-YMAX
KI=MXMAX-1
DO KX=2,KI [
X=XPOS(KX)
Y1=REPS*(DELOX(KX,1)+DELOX(KX,2))
CALL PLOT (KCCB,X,Y1,KUPHOV)
CALL PLOT (KCCB,X,Y2,KDHNOV)
]
CALL PENUP(KCCB)
..... DRAW X-LINES
X1=XPOS(1)
X2=XPOS(MXMAX)
KI=NYMAX-1
IF ((TOXO.NE.0.0*(EXP)0).OR.(TOXI.NE.0.0*(EXP)0)) [
DO KY=2,KI [
Y=YPOS(KY)
CALL PLOT (KCCB,X1,Y,KUPHOV)
CALL PLOT (KCCB,X2,Y,KDHNOV)
]
CALL PENUP (KCCB)
]
DO KY=2,KI [
Y=YPOS(KY)
CALL PLOT (KCCB,X1,Y,KUPHOV)
CALL PLOT (KCCB,X2,Y,KDHNOV)
]
CALL PENUP(KCCB)
..... FINISH UP

```

File: &PLOTM

```

IF (LU.EQ.LUPLTR) CALL PEN (KCCB,0)
CALL PLOTM (KCCB ,KTYPE,0)
.....RING BELL AND TURN ON ALPHA DISPLAY
WRITE (KONSOL,3000) KBELL,KESC
FORMAT(2R1,"dE-")
.....FROM CONSOL TO PLOTTER
KCO=0
IF (LU.NE.LUPLTR) [
WRITE (KONSOL,6000)
READ (KONSOL,2000) KANSUR
FORMAT("Replot on the plotter (Yes=f7/No=f8) ? _")
FORMAT(A1)
IF (KANSUR.EQ.KYES) [
KCO=1
LU=LUPLTR
]
]
]
]
..... DONE
RETURN
END

```


File: &POSHI

```
      ]
      KOUNT=KOUNT+1
      ] UNTIL ((ABSERR.LE.ATOL1).OR.(KOUNT.GE.KMAX))
0
0.....WRITE OUT PROPER MESSAGE
      IF (KMSG.NE.0) [
      LOCIT=MOD(KOUNT,10)
      IF (LOCIT.EQ.1) WRITE (KONSOL,1000) LOC,KOUNT,NORDER(1),ABSERR
      ELSE [
      IF (LOCIT.EQ.2) WRITE (KONSOL,1000) LOC,KOUNT,NORDER(2),ABSERR
      ELSE [
      IF (LOCIT.EQ.3) WRITE (KONSOL,1000) LOC,KOUNT,NORDER(3),ABSERR
      ELSE
      WRITE (KONSOL,1000) LOC,KOUNT,NORDER(4),ABSERR
      ]
      ]
1000 FORMAT ("Initialize column",I3,"1",^
           "Converged at",I3,"A2," iteration, maximum deviation ="G10.3)
      ]
0
0.....DONE
      RETURN
      END
```

File: &POSSH

```
0
0.....CALL TWDEFM
0
0.....IF HP1000
      ENA(XYZ,0)
0
0.....ENDIF
      SUBROUTINE POSSH
0
0.....SOLVE 2-D POISSON DIFFERENCE EQUATION
0
0.....CALL TEHA
0.....CALL TCOHNN
0
0.....DIMENSION KITR(50,49),NORDER(4)
0
0.....EQUIVALENCE ENA ARRAYS INTO ONE-DIMENSIONAL ARRAYS
      DIMENSION ODCONC(1),ODPOTS(1),ODCNOR(1),ODCSOU(1),ODCEAS(1),ODCVES(1),^
      ODGONE(1),ODCARR(1)
      EQUIVALENCE (ODCONC(1),CONC(1,1)), (ODPOTS(1),POTS(1,1)),^
      (ODCNOR(1),CNORTH(1,1)),(ODCSOU(1),CSOUTH(1,1)),^
      (ODCEAS(1),CEAST(1,1)), (ODCVES(1),CVEST(1,1)),^
      (ODGONE(1),GONE(1,1)), (ODCARR(1),CARRIE(1,1))
0
0.....DATA NORDER/2Hst,2Hnd,2Hrd,2Hth/, KYES/2HY /
0.....IF HP1000
      DATA KEBC/033B/, KCR/015B/
0.....ENDIF
0
0.....KPASS=1
0
0.....CHECK IF ENVOKE LOCAL ITERATION
      KLITR=KMAX2+1
      IF (RELAX2.EQ.1) [
      WRITE (KONSOL,1050)
1050 FORMAT("Envoke local iteration (Yes=f7/No=f0) ? _")
      READ (KEYBRD,2000) KANSUR
0.....IF BATCH
      WRITE (KONSOL,2000) KANSUR
0.....ENDIF
      IF (KANSUR.EQ.KYES) [
      WRITE (KONSOL,1060)
1060 FORMAT("Start from ? iteration ? _")
      READ (KEYBRD,0) KLITR
0.....IF BATCH
      WRITE (KONSOL,1061) KLITR
1061 FORMAT(I4)
0.....ENDIF
      WRITE (KONSOL,1070)
1070 FORMAT("Convergence information per grid (Yes=f7/No=f0) ? _")
      READ (KEYBRD,2000) KANSUR
0.....IF BATCH
      WRITE (KONSOL,2000) KANSUR
0.....ENDIF
      IF (KANSUR.EQ.KYES) KINSG1=1
      ELSE
      KINSG1=0
      ]
      ]
2000 FORMAT(A1)
0
0.....INITIALIZE EVENT TABLE
      NY1=NYMAX+1
      DO N=1,NXMAX [
      DO M=1,NY1; KITR(N,M)=0
      IF (DELOX(N,2).EQ.0.0(EXP>0)) KITR(N,1)=9
      IF (DELOX(N,1).EQ.0.0(EXP>0)) KITR(N,2)=9
      ]
0
0.....PREPARE FOR ITERATION
      NX2=NXMAX-1
      NY2=NYMAX-1
      DYN=DELY(NY2)
      JUNK=IFBRK(0)
      TOTSK=0.0E0
      PRCHT=100.0E0/FLOAT(NXMAX*NYMAX)
      KOUNT=0
      KCD=1
      HCO=(NSOURC+NDRAIN)/2
      HCO=1
0
0.....ALTERNATE X-LOOP DIRECTION EVERY OTHER ONE
      REPEAT [
      IF (IFBRK(0).EQ.0) [
0 reset BRK flag
0 reset SKIP count
0 reset loop count
0 set GO flag
0 set channel center indice
```



```

      ] ELSE DOPE(KKINP)=K
    ]
0 ..... READ VALUES
  ELSE [
0 ..... SUBSTRATE CONCENTRATION
  *IF BATCH
    READ (KEYBRD,*) ANS0,ANS1,ANS2
    IF ((KPARM.EQ.4).OR.(KPARM.EQ.10).OR.(KPARM.EQ.13))
      WRITE (KONSOL,2001) ANS0,ANS1,ANS2
    ELSE IF (KPARM.EQ.8) WRITE (KONSOL,2001) ANS0,ANS1
    ELSE WRITE (KONSOL,2001) ANS0
    FORMAT(IPJG13.3)
  *ENDIF
0 ..... INPLANT WINDOW
  IF (KPARM.EQ.2) CSUB=ANS0*1.0<EXP>15
0 ..... INPLANT PARAMETERS
  ELSE [
    IF (KPARM.LT.8) KK=KPARM
    ELSE KK=KPARM-1
    KK=(KK-2)/5
    IF (KK.EQ.2) [
      RANGE(KKINP)=ANS0*UM
      STNOV(KKINP)=AMAX1(ANS1*UM,0.0<EXP>0)
      DOSE(KKINP)=SIGN(ANS2,DTYPE)
    ]
    IF (KK.EQ.3) DCOEF(KKINP)=AMAX1(ANS0,0.0<EXP>0)
    IF (KK.EQ.4) TEMP(KKINP)=ANS0
    IF (KK.EQ.5) DRVIN(KKINP)=AMAX1(ANS0*SECND,0.0<EXP>0)
  ]
0 ..... ANY MORE CHANGES?
  WRITE (KONSOL,1040)
  1040 FORMAT('More changes (Yes=f7/No=f8) ? -')
  *IF BATCH
    READ (KEYBRD,2000) KANSUR
  *ENDIF
  WRITE (KONSOL,2000) KANSUR
  IF (KANSUR.EQ.KYES) KGO=1
  ELSE KGO=0
  ] UNTIL (KGO.EQ.0)
0 ..... PROCESS PARAMETERS OF STEP APPROXIMATION
  DO KINPL=1,3 IF (ABS(DOSE(KINPL)).GT.1.0<EXP>0) CALL ASTEP(KINPL)
]
0 ..... DONE
  RETURN
  END

```

```

*CALL TUNDEFM
SUBROUTINE RDFGM
0
0 REDEFINE DEVICE GEOMETRY
*CALL TCONMM
0
DATA KYES/2HY /, UM/1.0<EXP>-4/
0 ..... CHANGE ALL
  WRITE (KONSOL,1000)
  1000 FORMAT('Change all geometry parameters (Yes=f7/No=f6) ? -')
  READ (KEYBRD,2000) KANSUR
  *IF BATCH
    WRITE (KONSOL,2000) KANSUR
  *ENDIF
  2000 FORMAT(A1)
  IF (KANSUR.EQ.KYES) CALL REDGN
0 ..... CHANGE PART OF THEM
  ELSE [
    WRITE (KONSOL,1010)
    1010 FORMAT(
      /GX, 'drawn channel length (um)..... 1--
      /GX, 'lateral span of source (um)..... 2--
      /GX, 'lateral span of drain (um)..... 3--
      /GX, 'oxide thickness: thin? and thick? (um)... 4--
      /GX, 'thin oxide location: from ? to ? (um)... 5--
      /GX, 'lateral span of oxide ramp (um)..... 6--
      /GX, 'drawn gate location: from ? to ? (um)... 7--
      /GX, 'depth of the simulated structure (um).... 8--
    )
0 ..... READ INDEX AND VALUE(S)
  REPEAT [
    WRITE (KONSOL,1020)
    1020 FORMAT('Which one? (Enter index) ? -')
    READ (KEYBRD,*) KPARM
  *IF BATCH
    WRITE (KONSOL,1021) KPARM
    1021 FORMAT(I3)
  *ENDIF
  WRITE (KONSOL,1030)
  1030 FORMAT('Value(s) ? *')
  READ (KEYBRD,*) ANS0,ANS1
0 ..... SCALE AND LOAD NEW VALUES
  PARM0=AMAX1(ABS(ANS0)*UM,0.0<EXP>0)
  PARM1=AMAX1(ABS(ANS1)*UM,0.0<EXP>0)
  IF (KPARM.EQ.1) XCHANL=PARM0
  IF (KPARM.EQ.2) XSOURC=PARM0
  IF (KPARM.EQ.3) XDRAIN=PARM0
  IF (KPARM.EQ.4) [ TOK0=PARM0; TOK1=PARM1 ]
  IF (KPARM.EQ.5) [ XD0=PARM0; XD1=PARM1 ]
  IF (XOX0.GT.XOX1) [ T=XOX0; XOX0=XOX1; XOX1=T ]
  ]
  IF (KPARM.EQ.6) XOXR=PARM0
  IF (KPARM.EQ.7) [ XGATE0=PARM0; XGATE1=PARM1 ]
  IF (XGATE0.GT.XGATE1) [ T=XGATE0; XGATE0=XGATE1; XGATE1=T ]
  ]
  IF (KPARM.EQ.8) YMAX=PARM0
0 ..... ANY MORE ?
  WRITE (KONSOL,1040)
  1040 FORMAT('More changes (Yes=f7/No=f8) ? -')
  READ (KEYBRD,2000) KANSUR
  *IF BATCH
    WRITE (KONSOL,2000) KANSUR
  *ENDIF
  IF (KANSUR.EQ.KYES) KGO=1
  ELSE KGO=0
  ] UNTIL (KGO.EQ.0)
0 ..... UPDATE XMAX
  XMAX=XCHANL+XSOURC+XDRAIN
]
0 ..... DONE
  RETURN
  END

```



```

*CALL TDEFH
SUBROUTINE RDEF1
0
0 READ INPUT PARAMETERS FROM A FILE
0
*CALL TCONHN
0
DIMENSION KDOPE(6),NANINP(4,3)
0
0... FILE MANAGEMENT PARAMETERS
*IF HP1000
DIMENSION HANBUF(10),NSTRNG(20),MANFIL(3),^
KDCB(144), KSIZE(2), KBUF(40)
0
EQUIVALENCE (HANBUF(1),MANFIL(1)),(HANBUF(9),NSECU),(HANBUF(6),NCR)
0
DATA KSIZE/20,00/,KTYPE/3/,KDCB/120/,^
LRECL/40/, NSECU/6/,NCR/2HXX/
*ENDIF
0
DATA KDOPE/2H0,2HA,2HP,2HS,2H+,2H-, /, KDSUP/2HF /,^
NANINP/2H0v,2H0r,2H0l,2H1,^
2H1o,2H1c,2H1,2Hd,^
2Hs,2Hc/,2Hr,2Hn /
*IF HP1000
DATA HANSTR/2H00/
*ENDIF
0
DATA KESC /0330/
0
0... GET THE DATA FILE NAME
*IF HP1000
KOPEN=1
WHILE (KOPEN.EQ.1) [
1000 WRITE (KONSOL,1000)
FORMAT("Input data file name? -")
READ (KEYBRD,1010) NSTRNG
NPOS=1) CALL NARR (HANBUF,NSTRNG,40,NPOS)
DO K=1,10) INPFIL(K)=HANBUF(K)
0
0... OPEN THE FILE
CALL OPEN (KDCB,KERR,MANFIL,0,NSECU,NCR,KDCB)
KOPEN=0
IF (KERR.LT.0) CALL TFERR(1,KERR,HANBUF,KOPEN)
*ELSE
]
0
*ELSE
READ (KEYBRD,1010) NSTRNG
KERR=0
*ENDIF
*IF BATCH
WRITE (KONSOL,1000)
WRITE (KONSOL,1010) NSTRNG
*ENDIF
1010 FORMAT(20A2)
0
0... RESET ERROR FLAG AND SKIP TITLE
IF (KERR.GE.0) [
KEXIT=0
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
*ELSE
READ (LURDI,1010) IDUNNY IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
0
0... GEOMETRY PARAMETERS
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XCHANL
*ELSE
READ (LURDI,*) XCHANL IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
0
0... CHECK IF FATAL ERROR
IF (XCHANL.LE.0.0) GO TO 800
0
0... CONTINUE READING
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XSOURCE
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XDRAIN

```

```

CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) TOX0,TOX1
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XOX0,XOX1
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XOXR
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XGATE0,XGATE1
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) YMAX
*ELSE
READ (LURDI,*) XSOURCE IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) XDRAIN IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) TOX0,TOX1 IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) XOX0,XOX1 IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) XOXR IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) XGATE0,XGATE1 IF (EOF(LURDI).NE.0.0E0) GO TO 900
READ (LURDI,*) YMAX IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
0
0... PRINT INPUT SUMMARY
WRITE (KONSOL,3010) (HANSTR,K=1,20),XCHANL,XSOURCE,XDRAIN,^
TOX0,TOX1,XOX0,XOX1,XOXR,XGATE0,XGATE1,YMAX
3010 FORMAT(14A2,3X,"INPUT SUMMARY",3X,14A2^
//3X,"Draw channel length",F7.3,"um"
//3X,"Lateral span of source",F7.3,"um"
//3X,"Lateral span of drain",F7.3,"um"
//3X,"Oxide thickness: thin/thick",F7.3,"",F7.3,"um"
//3X,"Thin oxide loc: fron/to",F7.3,"",F7.3,"um"
//3X,"Lateral oxide ramp",F7.3,"um"
//3X,"Draw gate loc: fron/to",F7.3,"",F7.3,"um"
//3X,"Structure depth",F7.3,"um")
0
0... SCALE AND LIMIT GEOMETRY PARAMETERS
CALL CHKGN
0
0... READ SUPREN FLAG
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,2000) KB
*ELSE
READ (LURDI,2000) KB IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
2000
FORMAT(A1)
IF (KB.EQ.KDSUP) [
KBSUPR=1
WRITE (KONSOL,2010)
FORMAT("Use SUPREN generated profile.")
2010
]
ELSE [
KBSUPR=0
0
0... READ IN IMPLANT PARAMETERS
K=1) WHILE ((KB.NE.KDOPE(K)).AND.(K.LE.6)) K=K+1
IF (K.GT.6) GO TO 801
IF ((K.EQ.1).OR.(K.EQ.6)) TYPE=-1.0
ELSE
TYPE=1.0
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND) IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) CSUB
*ELSE
READ (LURDI,*) CSUB IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
IF (CSUB.EQ.0.0E0) GO TO 802
CSUB=SIGN(CSUB*IE15,TYPE)
WRITE (KONSOL,3000) KB,CSUB
3000
FORMAT(3X,"Substrate dopant:",A1,^
", concentration=",1PG10.3,"cm-3")
DO K=1,3 [
*IF HP1000
IF (K=1) [
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2) READ (KBUF,*) XINPLO,XINPL1
*ELSE
READ (LURDI,*) XINPLO,XINPL1
IF (EOF(LURDI).NE.0.0E0) GO TO 900
*ENDIF
]
*IF HP1000

```

File: &REDF1

```
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900; CALL CODE (KEND*2)
READ (KBUF,2000) KD
*ELSE
*ENDIF
READ (LURD1,2000) KD; IF (EOF(LURD1).NE.0.0E0) GO TO 900
K=1; WHILE ((KD.NE.KDOPE(K)).AND.(K.LE.6)) K=K+1
DOPE(KINPL)=K
*IF NP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900; CALL CODE (KEND*2)
READ (KBUF,*) RANGE(KINPL),STDEV(KINPL),DOSE(KINPL)
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900; CALL CODE (KEND*2)
READ (KBUF,*) DCOEF(KINPL)
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900; CALL CODE (KEND*2)
READ (KBUF,*) TEMP(KINPL)
CALL READF (KDCB,KERR,KBUF,LRECL,KEND)
IF (KEND.EQ.-1) GO TO 900; CALL CODE (KEND*2)
READ (KBUF,*) DRVIN(KINPL)
*ELSE
READ (LURD1,*) RANGE(KINPL),STDEV(KINPL),DOSE(KINPL)
IF (EOF(LURD1).NE.0.0E0) GO TO 900
READ (LURD1,*) DCOEF(KINPL)
IF (EOF(LURD1).NE.0.0E0) GO TO 900
READ (LURD1,*) TEMP(KINPL)
IF (EOF(LURD1).NE.0.0E0) GO TO 900
READ (LURD1,*) DRVIN(KINPL)
IF (EOF(LURD1).NE.0.0E0) GO TO 900
*ENDIF
0.....PRINT INPUT SUMMARY
IF ((DOPE(KINPL).LE.6.0).AND.(DOSE(KINPL).NE.0.0E0)) I
WRITE (KONSOL,3020) (NAMINP(K,KINPL),K=1,4),KD,^
RANGE(KINPL),STDEV(KINPL),^
DOSE(KINPL),DCOEF(KINPL),^
TEMP(KINPL),DRVIN(KINPL)
3020 FORMAT(5X,4I2,"implant dopant=",A1,^
/,10X,"Range(un),", 8I2V(un), " Dose(cn-2)=",^
2X,F7.3, ", ",F7.3, ", ",1PG10.3^
/,10X,"D-coeff(cn2/sec), Temp(oC), Drive-in(min)",^
G10.3, ", ",OPF7.1, ", ",F7.3)
0.....SCALE AND LIMIT INPLANT PARAMETERS
CALL CHKDP (KINPL)
]
ELSE [
DOSE(KINPL)=0.0E0
XJCT(KINPL)=0.0E0
]
]
]
0.....SET ERROR EXIT FLAG
ELSE KEXIT=1
0
0.....CLOSE THE FILE
500 CONTINUE
*IF NP1000
CALL CLOSE (KDCB,KERR)
IF (KERR.LT.0) CALL TFERR (2,KERR,HANBUF)
*ENDIF
0
0.....DONE
IF (KEXIT.EQ.0) RETURN
0
0.....ERRORDUS EXIT, REMEMBER TO UNLOCK DISPLAY MEMORY
ELSE [
*IF NP1000 IBATCH
WRITE (KONSOL,5000) KEBC
5000 FORMAT(1I,"n")
CALL EXEC (6)
*ELSE
STOP
*ENDIF
]
0
0.....ERROR IN INPUT DATA
```

File: &REDF1

```
800 CONTINUE
KEXIT=1
WRITE (KONSOL,8000)
FORMAT("***** Channel length (= 0) Program terminated! *****")
GO TO 500
801 CONTINUE
KEXIT=1
WRITE (KONSOL,8001)
8001 FORMAT("***** Substrate dopant undefined! Program terminated! *****")
GO TO 500
802 CONTINUE
KEXIT=1
WRITE (KONSOL,8002)
8002 FORMAT("** Zero substrate doping concentration! Program terminated! **")
GO TO 500
0
0.....ERROR IN FILE FORMAT
900 CONTINUE
KEXIT=1
WRITE (KONSOL,9000)
WRITE (KONSOL,9010)
WRITE (KONSOL,9020)
GO TO 500
9000 FORMAT("Input file is not properly created.",^
/,"The format should be:",^
/,"line 1: title line",^
/,"line 2: drawn channel length (un)",^
/,"line 3: lateral span of source (un)",^
/,"line 4: lateral span of drain (un)",^
/,"line 5: oxide thickness: thin? and thick ? (un)",^
/,"line 6: thin oxide location: from ? to ? (un)",^
/,"line 7: lateral span of oxide ramp (un)",^
/,"line 8: drawn gate location: from ? to ? (un)",^
/,"line 9: depth of the simulated structure? (un)",^
/,"line 10: substrate dopant: B,As,Ph,8b,(n-type),(p-type)",^
" F(Supren)")
9010 FORMAT("line 11: substrate doping concentration (E15 cn-3)",^
/,"line 12: overall implant dopant: B, As, Ph, 8b, +, -",^
/,"line 13: range(un), stdev(un) and dose (cn-2)",^
/,"line 14: diffusion constant (cn2/sec)",^
/,"line 15: drive in temperature (oC)",^
/,"line 16: drive in time (min)",^
/,"line 17: localized implant location: from ? to ? (un)",^
/,"line 18: dopant: B, As, Ph, 8b, +, -",^
/,"line 19: range, stdev and dose",^
/,"line 20: diffusion constant (cn2/sec)",^
/,"line 21: drive in temperature (oC)",^
/,"line 22: drive in time (min)",^
/,"line 23: source/drain implant dopant: B, As, Ph, 8b, +, -",^
/,"line 24: range, stdev and dose",^
/,"line 25: diffusion constant (cn2/sec)",^
/,"line 26: drive in temperature (oC)",^
/,"line 27: drive in time (min)")
END
```

```

*CALL TUDEFN
*IF HP1000
EMAC(NYZ,0)
*ENDIF
SUBROUTINE REDF2
  READ INPUT PARAMETERS FROM A FILE
*CALL TERA
*CALL TCOMN
  DIMENSION KDOPE(6)
  DIMENSION SUPBUF(5),SUPC(400),SUPY(400)
*IF HP1000
  ..... FILE MANAGEMENT PARAMETERS
  DIMENSION HANBUF(10),NSTRNG(20),HANFIL(3),^
  KDCBI(144),KSIZE(2), KBUF(40)
  EQUIVALENCE (HANBUF(1),HANFIL(1)),(HANBUF(5),HSECU),(HANBUF(6),NCR)
  DATA KSIZE/20,80/,KTYPE/3/,KDCBS/120/,^
  LRECL/40/, HSECU/6/,NCR/2HXX/
*ENDIF
  KSUB=0 -> UNIFORM SUBSTRATE, KSUB=1 -> NON-UNIFORM SUBSTRATE
  KB=DOPANT OF NON-UNIFORM SUBSTRATE DEVICE
  DATA KDOPE/2HD ,2HA ,2HP ,2HS ,2H+ ,2H- /, KDNUL/2H+ /
  DATA HOUNIF/2HH /, DN/1<EXP>-4/, SECND/60.0<EXP>0/, LENSUP/400/
*IF HP1000
  DATA KESC /0330/
*ENDIF
  ..... GET THE DATA FILE NAME
*IF HP1000
  DO K=1,10) HANBUF(K)=INPFIL(K)
  CALL OPEN (KDCBI,KERR,HANFIL,0,HSECU,NCR,KDCBS)
  KOPEN=0
  IF (KERR.LT.0) CALL YFERR(1,KERR,HANBUF,KOPEN)
  WHILE (KOPEN.EQ.1) [
    WRITE (KONSOL,1000)
    READ (KEYBRD,1010) NSTRNG
    FORMAT("Input data file name? ")
    NPOS=1) CALL NAME (HANBUF,NSTRNG,40,NPOS)
    DO K=1,10) INPFIL(K)=HANBUF(K)
  ]
  ..... OPEN THE FILE
  CALL OPEN (KDCBI,KERR,HANFIL,0,HSECU,NCR,KDCBS)
  KOPEN=0
  IF (KERR.LT.0) CALL YFERR(1,KERR,HANBUF,KOPEN)
*ELSE
  KERR=0
*ENDIF
  ..... RESET ERROR FLAG, SKIP FIRST 10 LINES
  1010 FORMAT(20A2)
  IF (KERR.GE.0) [
    KEXIT=0
*IF HP1000
    DO K=1,10 [
      CALL READF (KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
    ]
*ENDIF
  2000 FORMAT(A1)
  ..... READ IN SUBSTRATE INFORMATIONS
*IF HP1000
  CALL READF (KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
  CALL CODE (KEND+2); READ (KBUF,2000) KANSUB
*ELSE
  READ (LURDI,2000) KANSUB; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
  K=1) WHILE ((KANSUB.NE.KDOPE(K)).AND.(K.LE.6)) K=K+1
  IF (K.GT.6) GO TO 801
  IF ((K.EQ.1).OR.(K.EQ.6)) DOPE=-1.0<EXP>0
  ELSE TYPE=1.0<EXP>0
  IF (TYPE.EQ.-1.0<EXP>0) KB=6
  ELSE KB=5

```

```

*IF HP1000
  CALL READF (KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
  CALL CODE (KEND+2); READ (KBUF,2000) KANSUB
*ELSE
  READ (LURDI,2000) KANSUB; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
  IF (KANSUB.NE.NOUNIF) [
*IF HP1000
  CALL READF (KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
  CALL CODE (KEND+2); READ (KBUF,0) CSUB
*ELSE
  READ (LURDI,0) CSUB; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
  IF (CSUB.EQ.0.0<EXP>0) GO TO 802
  CSUB=SIGN(CSUB+1<EXP>15,TYPE)
  DO M=1,NKMAX) DO N=1,NYMAX) CONC(H,M)=CSUB
  KSUB=0
  WRITE (KONSOL,3000) KANSUB,CSUB
  3000 FORMAT(5X,"Uniform substrate of dopant: ",A1,"
  ", concentration=",1PG10.3,"cm-3")
  ]
  ELSE [
    KSUB=1
    CSUB=0.0<EXP>0
  ]
  ..... GET IMPLANT PROFILE
  DO KINPL=1,3 [
    IF (KSUB.LE.0) [
      IF (KINPL.EQ.2) [
*IF HP1000
        CALL READF (KDCBI,KERR,KBUF,LRECL,KEND)
        IF (KEND.EQ.-1) GO TO 900
        CALL CODE (KEND+2); READ (KBUF,0) XINPLO,XINPL1
*ELSE
        READ (LURDI,0) XINPLO,XINPL1
        IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
        XINPLO=XINPLO*UN
        XINPL1=XINPL1*UN
        IF (XINPLO.GT.XINPL1) [
          T=XINPLO; XINPLO=XINPL1; XINPL1=T
        ]
        XINPLO=LOCK(XINPLO)
        XINPL1=LOCK(XINPL1)
        IF (XINPLO.EQ.0) [ IF (XINPL1.NE.0) XINPLO=1 ]
        ELSE [ IF (XINPLO.NE.NPOS(XINPLO)) XINPLO=XINPLO+1 ]
      ]
*IF HP1000
        CALL READF(KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
        CALL CODE (KEND+2); READ (KBUF,2000) KANSUB1
*ELSE
        READ (LURDI,2000) KANSUB1; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
        KK=1) WHILE ((KANSUB1.NE.(KDOPE(KK))).AND.(KK.LE.6)) KK=KK+1
        IF ((KK.EQ.1).OR.(KK.EQ.6)) DOPE(KINPL)=6.0<EXP>0
        IF ((KK.GT.1).AND.(KK.LT.6)) DOPE(KINPL)=3.0<EXP>0
        IF (KK.GT.6) DOPE(KINPL)=0.0<EXP>0
      ]
      ELSE DOPE(1)=KB
      IF (DOPE(KINPL).NE.0.0<EXP>0) [
*IF HP1000
        CALL READF(KDCBI,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
        CALL CODE (KEND+2); READ (KBUF,0) SD
*ELSE
        READ (LURDI,0) SD; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
        STDV(KINPL)=SD*UN
      ]
      ..... READ IN PROFILE
*IF HP1000
        CALL READF(KDCBI,KERR,KBUF,LRECL,KEND)
        IF(KEND.EQ.-1) GO TO 900
        CALL CODE (KEND+2); READ (KBUF,1010) NSTRNG
*ELSE
        READ (LURDI,1010) NSTRNG; IF (EOF(LURDI).NE.0.0<EXP>0) GO TO 900
*ENDIF
      ]
      ..... GET COLUMN INDEX
*IF HP1000

```


File: &REDGH

File: &REDGH

```
•CALL TDEFH
SUBROUTINE REDGH
•
• READ IN GEOMETRY PARAMETERS
•
•CALL TCOMM
•
• DIMENSION MESSG1(3,2),MESSG2(3,2)
•
• DATA LMMSG1/3/,^
  MESSG1/2Hpo,2Hup,2Hce,^
  2Hdp,2Hai,2Hn /,^
  LMMSG2/3/,^
  MESSG2/2Hdr,2Haw,2Hn ,2Hga,2Hte,^
  2Hga,2Hte,2H o,2Hri,2Hde/
•IF HP1000
•ENDIF
•
• WRITE (KONBOL,1000)
1000 FORMAT("Drawn channel length (un) ? -")
  READ (KEYBRD,*) XCHANL
•IF BATCH
  WRITE (KONBOL,1001) XCHANL
1001 FORMAT(I2G10.3)
•ENDIF
  IF (XCHANL.LE.0.(EXP)0) GO TO 900
  WRITE (KONBOL,1010) (MESSG1(K,1),K=1,LMMSG1)
  READ (KEYBRD,*) XSDURC
•IF BATCH
  WRITE (KONBOL,1001) XSDURC
•ENDIF
  WRITE (KONBOL,1010) (MESSG1(K,2),K=1,LMMSG1)
1010 FORMAT("Lateral span of ".3A2." ? (un) -")
  READ (KEYBRD,*) XDRAIN
•IF BATCH
  WRITE (KONBOL,1001) XDRAIN
•ENDIF
  WRITE (KONBOL,1030)
1030 FORMAT("Oxide thicknesses -> gate and field (un) ??-")
  READ (KEYBRD,*) TON0,TOX1
•IF BATCH
  WRITE (KONBOL,1001) TON0,TOX1
•ENDIF
  WRITE (KONBOL,1020) (MESSG2(K,2),K=1,LMMSG2)
  READ (KEYBRD,*) XON0,XOX1
•IF BATCH
  WRITE (KONBOL,1001) XON0,XOX1
•ENDIF
  WRITE (KONBOL,1040)
1040 FORMAT("Span of oxide ramp (un) ? -")
  READ (KEYBRD,*) XOXR
•IF BATCH
  WRITE (KONBOL,1001) XOXR
•ENDIF
  WRITE (KONBOL,1020) (MESSG2(K,1),K=1,LMMSG2)
1020 FORMAT("3A2," location! from ( ) to ( ) (un) ? -")
  READ (KONBOL,*) XGATE0,XGATE1
•IF BATCH
  WRITE (KONBOL,1001) XGATE0,XGATE1
•ENDIF
  WRITE (KONBOL,1060)
1060 FORMAT("Depth of the simulated structure (un) ? -")
  READ (KEYBRD,*) YMAX
•IF BATCH
  WRITE (KONBOL,1001) YMAX
•ENDIF
•
•.....SCAEL INPUT PARAMETERS
  CALL CHKCH
•
•.....DONE
  RETURN
•
•.....ERROROUS EXIT -> REMEMBER TO UNLOCK DISPLAY MEMORY
900 CONTINUE
  WRITE (KONBOL,9000)
9000 FORMAT("***** Channel length (= 0) Program terminated! *****")
•IF HP2640A
  WRITE (KONBOL,9010) KESC
```

```
9010 FORMAT(RI,"n")
•ENDIF
•IF HP1000!BATCH
  CALL EXFC (6)
•ELSE
  STOP
•ENDIF
END
```

```

*CALL TDEFH
*IF HP1000
EMA (KY2,0)
*ENDIF
SUBROUTINE REDSP (KINPL,ICOLHN,NSTRNG)
READ PROFILE DISTRIBUTION FROM SUPREN'S SAVE FILE
*CALL TEMA
*CALL TCONHN
*.....BUFFER
DIMENSION SUPBUF(5),SUPC(400),SUPY(400),NAMIMP(4,3)
*IF HP1000
*.....FILE MANAGEMENT PARAMETERS
DIMENSION NAMBUF(10),NSTRNG(20),NAMFIL(3),^
KDCR(144),KSIZE(2),KRUFL(40)
EQUIVALENCE (NAMBUF(1),NAMFIL(1)),(NAMBUF(5),NSECUN),
(NAMBUF(6),NCR)
DATA KSIZE/20,80/,KTYPE/3/,KDCBS/128/,LRECL/40/,NSECUN/0/,NCR/2HXX/
*ENDIF
*.....SUPREN ARRAY LENGTH
DATA LENSUP/400/
*.....NAME OF IMPLANTS
DATA NAMIMP/2Hov,2Hov,2Hn1,2Hn1,^
2Hn1,2Hoc,2Hn1,2Hd,^
2Hsp,2Hc/,2Hnr,2Hn /
*.....SCALING FACTORS
DATA UM/1<EXP>-4/,SECND/60.0<EXP>0/
*IF HP1000
*.....ESCAPE CODE
DATA KESC/033B/
*.....OPEN SUPREN SAVE FILE
NPOS=1; CALL NARR (NAMBUF,NSTRNG,40,NPOS)
CALL OPEN (KDCB,KERR,NAMFIL,0,NSECUN,NCR,KDCBS)
KOPEN=0; IF (KERR.LT.0) CALL TFERR (1,KERR,NAMBUF,KOPEN)
WHILE (KOPEN.EQ.1) [
WRITE (KONSOL,3000) KINPL
READ (KEYBRD,1010) NSTRNG
3000 FORMAT('Implant',I2,' data file name? ')
NPOS=1; CALL NARR (NAMBUF,NSTRNG,40,NPOS)
]
*.....OPEN THE FILE
CALL OPEN (KDCB,KERR,NAMFIL,0,NSECUN,NCR,KDCBS)
KOPEN=0; IF (KERR.LT.0) CALL TFERR(1,KERR,NAMBUF,KOPEN)
]
*ELSE
KERR=0
*ENDIF
*.....EXIT IF ERROR
IF (KERR.LT.0) GO TO 900
1010 FORMAT(20A2)
*.....SKIP TITLE, COMMENT AND STEP INFO
DO K=1,3 [
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
*ELSE
READ (LURD2,1010) DUMMY; IF (EOF(LURD2).NE.0.0<EXP>0) GO TO 900
*ENDIF
]
*.....GRID INFO
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2); READ (KBUF,5010) DYS1,INTF,IPNT1,NCC,LEVEL
*ELSE
READ (LURD2,5010) DYS1,INTF,IPNT1,NCC,LEVEL
IF (EOF(LURD2).NE.0.0<EXP>0) GO TO 900
*ENDIF
5010 FORMAT(G13.4,4I3)

```

```

*.....SKIP OXIDE CONCENTRATION
INTF1=INTF-1
DO K=1,INTF1 [
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
*ELSE
READ (LURD2,0) (DUMMY,KK=1,5); IF (EOF(LURD2).NE.0.0<EXP>0) GO TO 900
*ENDIF
]
*.....INITIALIZE BUFFER
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2); READ (KBUF,5020) (SUPBUF(K),K=1,5)
*ELSE
READ (LURD2,5020) (SUPBUF(K),K=1,5)
IF (EOF(LURD2).NE.0.0<EXP>0) GO TO 900
*ENDIF
5020 FORMAT(5G13.6)
SUPY(1)=0.0<EXP>0
SUPC(1)=ABS(SUPBUF(1COLHN))
*.....READ IN THE PROFILE, SEARCH FOR CONCENTRATION PEAK
KSTOP=LENSUP-INTF1
KGRID=IPNT1-INTF1
KMAX=0
DYS1=DYS1*UM
DYS14=4.0<EXP>0*DYS1
CMAX=0.0<EXP>0
DO KP=2,KSTOP [
*IF HP1000
CALL READF (KDCB,KERR,KBUF,LRECL,KEND); IF (KEND.EQ.-1) GO TO 900
CALL CODE (KEND*2); READ (KBUF,5020) (SUPBUF(K),K=1,5)
*ELSE
READ (LURD2,5020) (SUPBUF(K),K=1,5)
IF (EOF(LURD2).NE.0.0<EXP>0) GO TO 900
*ENDIF
SUPC(KP)=ABS(SUPBUF(1COLHN))
IF (KP.LT.KGRID) SUPY(KP)=SUPY(KP-1)+DYS1
ELSE SUPY(KP)=SUPY(KP-1)+DYS14
IF (CMAX.LT.SUPC(KP)) [
KMAX=KP
CMAX=SUPC(KP)
]
]
RANGE(KINPL)=SUPY(KMAX)
CPK=CMAX
*IF HP1000
*.....CLOSE THE SAVE FILE
CALL CLOSE(KDCB,KERR)
*ENDIF
*.....SEARCH FOR THE JUNCTION DEPTH
IF (CSUB.EQ.0.0<EXP>0) [
CSUB=SIGN(SUPC(KSTOP),TYPE)
ABSUB=ABS(CSUB)
CPK=CPK-ABSUB
DO K=1,KSTOP [
SUPC(K)=AMAX1(SUPC(K)-ABSUB,0.0<EXP>0)
DO M=1,MKMAX; DO N=1,NYMAX; CONC(N,M)=CSUB
]
3030 WRITE (KONSOL,3030) CSUB
FORMAT(5X,'Non-uniform substrate with ',^
'background concentration = ',IPG10.3,'cn-3')
]
ELSE ABSUB=ABS(CSUB)
KJCT=KMAX
CPEAK(KINPL)=CPK
REPEAT [
KJCT=KJCT+1
IF (SUPC(KJCT).LE.ABSUB) KGO=0
ELSE KGO=1
IF ((KGO.EQ.1).AND.(KJCT.GE.KSTOP)) KGO=-1
] UNTIL (KGO.LE.0)
XJCT(KINPL)=SUPY(KJCT)
*.....GET STANDARD DEVIATION OF APPROXIMATED GAUSSIAN DISTRIBUTION
SIGMA=ABS(XJCT(KINPL)-RANGE(KINPL))/SQRT(2.0<EXP>0*ALOG(CPK/ABSUB))
TWOPI=44.0<EXP>0/7.0<EXP>0

```

```

TUODT=SIGMA*SIGMA
DOSE(KINPL)=SQRT(TUODT*TUOP1)*CPK
IF (XJCT(KINPL).NE.0.0<EXP>0) CSTEP(KINPL)=DOSE(KINPL)/XJCT(KINPL)
ELSE CSTEP(KINPL)=0.0<EXP>0
0
0..... PARAMETERS
KDOPE=DOPE(KINPL)
IF (KDOPE.EQ.6) DTYPE=-1.0<EXP>0
ELSE DTYPE= 1.0<EXP>0
DO K=1,KSTOP; SUPC(K)=SIGN(SUPC(K),DTYPE)
DRVIN(KINPL)=1200.0<EXP>0
STNDV2=STNDV(KINPL)*STNDV(KINPL)
FDT=AMAX1(2.0<EXP>0*(TUODT-STNDV2),0.0<EXP>0)
DCDEF(KINPL)=0.25<EXP>0*FDT/DRVIN(KINPL)
0
0..... INTERPOLATE ION
CALL DOPS2 (KINPL,KSTOP,FDT,SUPY,SUPC)
0
0..... WRITE OUT APPROXIMATED IMPLANT PARAMETERS
WRITE (KONSOL,1050) (NAMINP(K,KINPL),K=1,4),^
DOSE(KINPL),SIGMA,^
CPEAK(KINPL),RANGE(KINPL),^
CSTEP(KINPL),XJCT(KINPL)
1050 FORMAT(/,"..... profile parameters of ",4A2," implant 1 ",^
/,10X,"total dose =",1PE10.3,"(ca-3)",^
6X,"standard D =",1PE10.3,"(ca)",^
/,10X,"peak conc =",1PE10.3,"(ca-3)",^
6X,"impl range =",1PE10.3,"(ca)",^
/,10X,"ave conc =",1PE10.3,"(ca-3)",^
6X,"lct depth =",1PE10.3,"(ca)"^
DOSE(KINPL)=SIGN(DOSE(KINPL),DTYPE)
CSTEP(KINPL)=SIGN(CSTEP(KINPL),DTYPE)
0
0..... DONE
RETURN
0
0..... ERROROUS EXIT, REMEMBER TO UNLOCK DISPLAY MEMORY
900 CONTINUE
*IF HP1000LATCH
WRITE (KONSOL,9000) KINPL,KESC; CALL ENEC (6)
9000 FORMAT("Data file of implant",I2," is not properly created.",R1,"n")
*ELSE
WRITE (KONSOL,9001) KINPL
9001 FORMAT("Data file of implant",I2," is not properly created.")
STOP
*ENDIF
END

```

```

*CALL TUDEFN
*IF HP1000
EMA(XYZ,0)
*ENDIF
0
0 SUBROUTINE SADDL
0
0 CHARACTERIZE SADDLE POINT
0
0 CALL TEMA
0 CALL YCONAN
0
0 DATA UM/1.0<EXP>4/, US0/700.0<EXP>0/
0
0 TUODT=VT300K+VT300K
0
0..... SEARCH THE LOCAL MAXIMA IN Y-DIRECTION
DO N=NSOURC,NDRAIN (
LMAX=1
PHAX=POTSI(N,1)
DO M=2,NYMAX; IF (POTSI(N,M).GT.PHAX) (
LMAX=M
PHAX=POTSI(N,M)
)
0
0..... IF IT IS ALSO THE MINIMUM IN X-DIRECTION -> THE SADDLE
IF ((LMAX.NE.1).AND.(POTSI(N+1,LMAX).GT.PHAX)^
.AND.(POTSI(N-1,LMAX).GT.PHAX)) (
XSADDL=XPOS(N)*UM
YSADDL=YPOS(LMAX)*UM
PBARR=POTSI(1,1)-PHAX
0
0..... DETERMINE THE WIDTH OF THE SADDLE
CALL WBASE (N,LMAX,NB1,NB2)
UBARR=XPOS(NB2)-XPOS(NB1)
0
0..... CALCULATE THE INJECTION CURRENT
CALL INTCA (N,LMAX,NB1,NB2,SUN)
CINJ0=C*VT300K*US0/UBARR
CINJ=ABS(CINJ0*SUN)
0
0..... SCALE AND WRITE THE RESULTS
CINJ=CINJ*UM
CINJ0=CINJ0*CHI*CHI/ABS((CONC(N,LMAX)))
HBY1=YPOS(NB1)*UM
HBY2=YPOS(NB2)*UM
HBARR=HBY2-HBY1
UBX1=XPOS(NB1)*UM
UBX2=XPOS(NB2)*UM
UBARR=UBARR*UM
WRITE (KONSOL,1000) PHAX,PBARR,XSADDL,YSADDL,N,LMAX,CINJ0,^
UBARR,UBX1,UBX2,NB1,NB2
IF (CINJ.NE.0.0<EXP>0)
WRITE (KONSOL,1020) HBARR,HBY1,HBY2,NB1,NB2,CINJ
)
0
0..... FORMAT STATEMENTS
1000 FORMAT("Saddle potential =",F6.3," barrier height=",F6.3,^
",",F6.3," un",F6.3," un",(" ",I2," ",I2,"")^
/,3X,"current density =",1PG10.3," Amp/cm2",^
/,3X,"Barrier width =",OPF6.3," un, from ",F6.3," un to ",F6.3,^
" un",(" ",I2," ",I2,"")^
1020 FORMAT(3X,"Barrier depth =",F6.3," un, from ",F6.3," un to ",F6.3,^
" un",(" ",I2," ",I2,"")^
/,3X,"Injection current /width =",1PG10.3," Amp/un",^
", with US0=700.0 ca2/sec-y")
0
0..... DONE
RETURN
END

```



```

*CALL TWDEFN
SUBROUTINE SAVIN
  SAVE INPUT PARAMETERS INTO DISC FILE
*CALL TCOMM
  DIMENSION KDOPE(6), MSGINP(4,3)
*IF HP1000
  ..... FILE MANAGEMENT PARAMETERS
  DIMENSION HANBUF(10), HSTRNG(20), HANFIL(3),
           KDCB(144), KSIZE(2), KBUF(40)
  EQUIVALENCE (HANBUF(1), HANFIL(1)), (HANBUF(5), MSEC), (HANBUF(6), NCR)
  DATA KSIZE/20,00/, KTYPE/3/, KDCBS/128/,
        LRECL/40/, MSEC/0/, NCR/2HXR/
*ENDIF
  DATA KDOPE/2ND ,2NA ,2NP ,2NB ,2H+ ,2H- /,
        MSGINP/2Hov,2Her,2Hn1,2M1 /,
              2H1o,2Hco,2H1',2Hd /,
              2Her,2Hc/,2Hdr,2Hn /,
        HANBLK/2H /, HANSTR/2H* /, HANMUL/2H0 /,
        UN/1<EXP>/, SECD/6.0<EXP>/
  ..... GET THE DATA FILE NAME
*IF HP1000
  KFILE=1
  WHILE (KFILE.EQ.1) [
    WRITE (KONSOL,1000)
    READ (KEYBD,1010) NSTRNG
    FORMAT('File name ? -')
    MPOS=1
    CALL NAHR (HANBUF,NSTRNG,40,MPOS)
  ]
  ..... CREAT/OPEN THE FILE
  CALL CREAT (KDCB,KERR,HANFIL,KSIZE,KTYPE,MSEC,NCR,KDCBS)
  KFILE=0
  IF (KERR.LY.0) [
    CALL OPEN (KDCB,KERR,HANFIL,0,MSEC,NCR,KDCBS)
    IF (KERR.LY.0) CALL TFERR(1,KERR,HANBUF,KFILE)
  ]
  IF (KERR.LY.0) GO TO 900
*ELSE
  READ (KEYBD,1010) NSTRNG
*ENDIF
*IF BATCH
  WRITE (KONSOL,1000)
  WRITE (KONSOL,1010) NSTRNG
*ENDIF
1010 FORMAT(20A2)
  ..... RESET ERROR FLAG, PRINT THE TITLE
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3000) (HANSTR,K=1,34) CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3000) (HANSTR,K=1,34)
*ENDIF
  ..... PRINT GEOMETRY PARAMETERS
  XPRNT=XCHANL*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3010) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3010) XPRNT
*ENDIF
  XPRNT=XSOURC*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3020) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3020) XPRNT
*ENDIF

```

```

XPRNT=XDRAIN*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3030) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3030) XPRNT
*ENDIF
  XPI=TOX0*UM
  XP2=TOX1*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3050) XPI,XP2; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3050) XPI,XP2
*ENDIF
  XPI=XOX0*UM
  XP2=XOX1*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3060) XPI,XP2; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3060) XPI,XP2
*ENDIF
  XPRNT=XONR*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3070) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3070) XPRNT
*ENDIF
  XPI=XGATE0*UM
  XP2=XGATE1*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3040) XPI,XP2; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3040) XPI,XP2
*ENDIF
  XPRNT=YMAX*UM
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3090) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3090) XPRNT
*ENDIF
  ..... PRINT INPLANT PARAMETERS
  IF (TYPE.GT.0.0<EXP>0) MPRNT=KDOPE(5)
  ELSE MPRNT=KDOPE(6)
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,4000) MPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,4000) MPRNT
*ENDIF
  XPRNT=ABS(CSUB)*1<EXP>-15
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,4010) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,4010) XPRNT
*ENDIF
  DO KIMPL=1,3 [
    IF (KIMPL.EQ.2) [
      XPI=XIMPL0*UM
      XP2=XIMPL1*UM
    ]
*IF HP1000
  DO K=1,LRECL; KBUF(K)=HANBLK; CALL CODE
  WRITE (KBUF,3080) XPI,XP2
  CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
  WRITE (LUWR,3080) XPI,XP2
*ENDIF

```

```

]
KPRNT=DOPE(KINPL)
IF (KPRNT.GT.0) NPRINT=KDOPE(KPRNT)
ELSE NPRINT=HAMNUL
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,4020) NPRINT,(MSGIMP(K,KINPL),K=1,4)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
*ENDIF
WRITE (LUNR,4020) NPRINT,(MSGIMP(K,KINPL),K=1,4)

XP1=RANGE(KINPL)*UN
XP2=STDEV(KINPL)*UN
XP3=ABS(DOSE(KINPL))
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,4030)XP1,XP2,XP3; CALL WRITF (KDCB,KERR,KBUF,LRECL)
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,4040) DCOEF(KINPL)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,4050) TEMP(KINPL)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUNR,4030) XP1,XP2,XP3
WRITE (LUNR,4040) DCOEF(KINPL)
WRITE (LUNR,4050) TEMP(KINPL)
*ENDIF
NPRINT=DRVIN(KINPL)/SECHD
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,4060) XPRNT; CALL WRITF (KDCB,KERR,KBUF,LRECL)
WRITE (LUNR,4060) XPRNT
]
*... CLOSE THE FILE
900 CONTINUE
*IF HP1000
CALL LOCF (KDCB,KERR,JUNK,KRB,JUNK,JSEC)
CALL CLOSE (KDCB,KERR,JSEC/2-KRB-1)
IF (KERR.LT.0) CALL TFERR (2,KERR,HAMBUF)
*ENDIF
*... DONE
RETURN
*... FORMAT STATEMENTS
3000 FORMAT(16A2,A1,4X,"TWIST",4X,16A2,A1)
3010 FORMAT(1P610.2,23X,"...drawn channel length (um)")
3020 FORMAT(1P610.2,23X,"...lateral span of source (um)")
3030 FORMAT(1P610.2,23X,"...lateral span of drain (um)")
3040 FORMAT(2(1P610.2),13X,"...drawn gate location: from ? to ? (um)")
3050 FORMAT(2(1P610.2),13X,"...oxide thickness: thin? and thick ? (um)")
3060 FORMAT(2(1P610.2),13X,"...thin oxide location: from ? to ? (um)")
3070 FORMAT(1P610.2,23X,"...lateral span of oxide ramp (um)")
3080 FORMAT(2(1P610.2),13X,"...localized implant: from ? to ? (um)")
3090 FORMAT(1P610.2,23X,"...depth of the simulated structure? (um)")
4000 FORMAT(A1,32X,"...substrate type: (s)-type, (-)p-type")
4010 FORMAT(1P610.2,23X,"...substrate doping concentration (*E15 cm-3)")
4020 FORMAT(A1,32X,"...4A2, implant dopant: B, As, Ph, Sb, *, -)
4030 FORMAT(3(1P610.2),3X,"...range(um), stdev(um) and dose (cm-2)")
4040 FORMAT(1P610.2,23X,"...diffusion constant (cm2/sec)")
4050 FORMAT(1P610.2,23X,"...drive-in temperature (oC)")
4060 FORMAT(1P610.2,23X,"...drive in time (min)")
END

```

```

*CALL TDEFM
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE SAVOU (MX1,MX2,MY1,MY2,X1,X2,Y1,Y2,Z1,Z2,KDISP,KELEC,KFELD)
*... SAVE RESULTS IN A FILE
*CALL TEMA
*CALL TCONNM
DIMENSION NSGDSP(10,4), NSGEAN(4,2), NSGFLD(6,4)
DIMENSION KDOPE(6),MSGIMP(4,3)
*IF HP1000
*... FILE MANAGEMENT PARAMETERS
DIMENSION HAMBUF(10),NSTRNG(20),HAMFIL(3),^
KDCB(400), KSIZE(2), KBUF(134)
EQUIVALENCE (HAMBUF(1),HAMFIL(1)),(HAMBUF(5),NSECU),(HAMBUF(6),NCR)
DATA KSIZE/200,134/,KTYPE/3/,KDCBS/304/,^
LRECL/67/, NSECU/0/,NCR/2HXX/, HAMBLK/2H /
*ENDIF
DATA LENDRP/10/, NUMDSP/4/,^
NSGDSP/2HD0,2HPI,2HNG,2H C,2HDN,2HCE,2HNT,2HRA,2HTI,2HDN,^
2HFR,2HEE,2H C,2HAR,2HRI,2HER,2H P,2HRO,2HF1,2HLE,^
2HF1,2HEL,2HD,2HDI,2HSR,2HR1,2HBU,2HTI,2HDN,2H ^,^
2HPO,2HTE,2HNT,2HIA,2HL,2H P,2HRO,2HF1,2HLE,2H ^,^
NSGEAN/2Hh1,2Hhc,2Htr,2Hn,^
2Hno,2Hlo,2H ^,2H ^,^
LENFLD/6/, NUMFLD/4/,^
NSGFLD/2HX-,2Hco,2Hnp,2Hn,2Hn,2Ht ^,^
2HY-,2Hco,2Hnp,2Hn,2Hn,2Ht ^,^
2Hra,2Hri,2Ho,2Hof,2H X,2HY,^
2Hra,2Hn,2Hit,2Hud,2He,2H ^,^
DATA KDOPE/2HD,2HA,2HP,2HS,2H+,2H- ^,^
NSGIMP/2Hov,2Hpr,2Hsl,2H1 ^,^
2Hlo,2Hca,2H1,2Hd ^,^
2Hsr,2Hc/,2Hdr,2Hn ^,^
HAMBLK/2H ^,^ HAMSTR/2H^/,^ HANDBUF/2H ^,^ NCPAGE/9/
*... GET THE FILE NAME
*IF HP1000
KFILE=1
WHILE (KFILE.EQ.1) {
WRITE (KONSOL,1000)
READ (KEYBRD,2000) NSTRNG
FORMAT(20A2)
NPOS=1
CALL HANR (HAMBUF,NSTRNG,40,NPOS)
}
*... CREATE/OPEN THE FILE
CALL CREAT (KDCB,KERR,HAMFIL,KSIZE,KTYPE,NSECU,NCR,KDCBS)
KFILE=0
IF (KERR.LT.0) {
CALL OPEN (KDCB,KERR,HAMFIL,0,NSECU,NCR,KDCBS)
IF (KERR.LT.0) CALL TFERR(1,KERR,HAMBUF,KFILE)
}
}
IF (KERR.LT.0) GO TO 900
*ELSE
READ (KEYBRD,2000) NSTRNG
*ENDIF
*IF BATCH
WRITE (KONSOL,1000)
WRITE (KONSOL,2000) NSTRNG
*ENDIF
1000 FORMAT("File name ? _")
*... THE TITLE
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBLK; CALL CODE
WRITE (KBUF,3000) (HAMSTR,K=1,60); CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUNR,3000) (HAMSTR,K=1,60)
*ENDIF
3000 FORMAT(29A2,A1,4X,"TWIST",4X,29A2,A1)

```

```

0...FUNCTION NAME
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,4000) NANDOT,(HSGDSP(K,KDISP),K=1,LENDSP),^
(HSGEAK(K,KELEC),K=1,4),(NANDOT,K=1,41)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,4000) NANDOT,(HSGDSP(K,KDISP),K=1,LENDSP),^
(HSGEAK(K,KELEC),K=1,4),(NANDOT,K=1,41)
*ENDIF
4000 FORMAT(A2,2X,10A2,2X," referring to ",4A2,1X,41A2)
0
IF (KDISP.EQ.3) (
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,4010) NANDOT,(HSGFLD(K,KFELD),K=1,LENFLD)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,4010) NANDOT,(HSGFLD(K,KFELD),K=1,LENFLD)
*ENDIF
4010 FORMAT(A2,34X,"(",6A2,")")
0
)
0...BAIS VOLTAGES
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,4020) NANDOT,VDB,VGB,VSB,(NANDOT,K=1,42)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,4020) NANDOT,VDB,VGB,VSB,(NANDOT,K=1,42)
*ENDIF
4020 FORMAT(A2,3(1PG10.2),"(VDB, VGB, VSB) ",41A2,A1)
0
)
0...DOMAIN DEFINITIONS
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,5010) Z1,Z2,(NANDOT,K=1,39); CALL WRITF(KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,5010) Z1,Z2,(NANDOT,K=1,39)
*ENDIF
5010 FORMAT(2X,2(1PG10.2),10X,"(Zmin,Zmax) estimated ",38A2,A1)
0
)
0...9 COLUMNS PER PAGE
NPAGE=(NX2-NX1)/NCPAGE
IF ((NX2-NX1).NE.(NPAGE*NCPAGE)) NPAGE=NPAGE+1
N2=NX1-1
NROW=NY2-NY1+1
DO KP=1,NPAGE (
N1=N2+1
N2=MIN0(N2+NCPAGE,NX2)
NCOL=N2-N1+1
)
0
)
0...BLANK LINE BETWEEN EACH PAGE
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,5555)
FORMAT(2X)
*ENDIF
5555
0
)
0...PRECEDE EACH BY COUNTS OF COLUMNS AND ROWS
*IF HP1000
CALL CODE; WRITE (KBUF,6000) NCOL,NROW,KP,(NANDOT,K=1,39)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,6000) NCOL,NROW,KP,(NANDOT,K=1,39)
*ENDIF
6000 FORMAT(2X,15,110,9X,"(column,row) on Page ",13,2X,39A2)
0
)
0...FOLLOWED BY X-COORDINATES
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,6005) (K,K=N1,N2)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,6010) (XPOS(K),K=N1,N2)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (LUWR,6005) (K,K=N1,N2)
WRITE (LUWR,6010) (XPOS(K),K=N1,N2)

```

```

*ENDIF
6005 FORMAT(11X,9(19,4X))
6010 FORMAT (2X,"Y(CN)X(CN)",4X,9(1PG9.2,4X))
0
)
0...DUMP THE NUMBERS
DO KY=NY1,NY2 (
*IF HP1000
DO K=1,LRECL; KBUF(K)=HAMBK; CALL CODE
WRITE (KBUF,7000) KY,YPOS(KY),(Z(K,KY),K=N1,N2)
CALL WRITF (KDCB,KERR,KBUF,LRECL)
*ELSE
WRITE (KBUF,7000) KY,YPOS(KY),(Z(K,KY),K=N1,N2)
*ENDIF
7000 FORMAT(12,1PG9.2,2X,9(1PG13.5))
)
0
)
0...CLOSE THE FILE
900 CONTINUE
*IF HP1000
CALL LOCF (KDCB,KERR,JUNK,IRB,JUNK,JSEC)
CALL CLOSE (KDCB,KERR,JSEC/2-IRB-1)
IF (KERR.LT.0) CALL TFERR(2,KERR,HAMBUF)
*ENDIF
0
)
0...DONE
RETURN
END

```

File: &SKEYD

```
*CALL TDEFN
SUBROUTINE SKEYD
0
0
0   DEFINE SOFT KEYS F1=DOPING F2=CARRIER F3=FIELD F4=POTENTIAL
*CALL TCOMM
0
0
0   IF HP1000
      DATA KESC/033B/
0   ENDIF
0
0   WRITE (KONSOL,1000) (KESC,K=1,4)
1000  FORMAT(R1,"&f1k2a6LDoping",^
           R1,"&f2k2a7LCarrier",^
           R1,"&f3k2a5LField",^
           R1,"&f4k2a9LPotential")
0
RETURN
END
```

File: &SKEYF

```
*CALL TDEFN
SUBROUTINE SKEYF
0
0
0   DEFINE SOFT KEYS   F1=X-COMPONENT   F2=Y-COMPONENT   F3=RATIO OF X/Y
                        F4=MAGNITUDE
*CALL TCOMM
0
0
0   IF HP1000
      DATA KESC/033B/
0   ENDIF
0
0   WRITE (KONSOL,1000) (KESC,K=1,4)
1000  FORMAT(R1,"&f1k2a11LX-component",^
           R1,"&f2k2a11LY-component",^
           R1,"&f3k2a12LRatio of X/Y",^
           R1,"&f4k2a9LMagnitude_")
0
RETURN
END
```

File: 4SKEYP

```
*CALL TUNDEFN
SUBROUTINE SKEYP
0
0   DEFINE SOFT KEYS F1=BORON   F2=ARSENIC  F3=PHOSPHORUS
0   F4=88            F5=*      F6=-
0
0 *CALL TCOMM
0
0 *IF HP1000
0   DATA KESC/033B/
0 *ENDIF
0
0 ..... DEFINE THE KEYS
0 WRITE (KONSOL,2000) (KESC,K=1,6)
2000 FORMAT(RI,"&f1k2a3Lboron",^
0         RI,"&f2k2a7LArsenic",^
0         RI,"&f3k2a10LPhosphorus",^
0         RI,"&f4k2a2L8b",^
0         RI,"&f5k2a9L*(N-type)",^
0         RI,"&f6k2a9L-(P-type)*")
0
0 ..... DONE
0 RETURN
0 END
```

File: 4SKEYT

```
*CALL TUNDEFN
SUBROUTINE SKEYT
0
0   DEFINE SOFT KEYS F1=2-dimensional plot F2=3-dimensional plot
0   F3=SAVE INTO DISC FILE F4=PRINT THE NUMBERS
0
0 *CALL TCOMM
0
0 *IF HP1000
0   DATA KESC/033B/
0 *ENDIF
0
0 WRITE (KONSOL,1000) (KESC,K=1,4)
1000 FORMAT(RI,"&f1k2a7L2D-plot",^
0         RI,"&f2k2a7L3D-plot",^
0         RI,"&f3k2a12Lsave on disc",^
0         RI,"&f4k2a14LPrint on paper")
0
0 RETURN
0 END
```

File: 4SOLVE

```
*CALL TUDFN
*IF HP1000
EMACHYZ,0)
*ENDIF
SUBROUTINE SOLVE (KSOLV)
POTENTIAL SOLUTION SEGMENT
KSOLV IS THE SECTION FLAG WHICH DENOTES THE RE-ENTRY POINT OF NEXT CALL
*CALL TENA
*CALL TCOMAN
DIMEHSION NARVLT(4)
*IF HP1000
DATA KEBC/033B/, KBELL/007B/
*ENDIF
DATA KYES/2NY /, NARSTR/2H**/, ITRMAX/10/,^
NARVLT /2ND ,2HG ,2HS ,2HB /
0
0.....INITIALIZATION
KINIT=1
KPITR=1
IF ((KSOLV.EQ.0).AND.(KLOOP.EQ.1)) [ KPHIS=0] KBIAS=0 ]
REPEAT [
0
0.....GET APPLIED VOLTAGES
IF (KSOLV.EQ.0) [
WRITE (KONSOL,1000)
FORMAT('Applied voltages: VD, VG, VS, VB ? -')
READ (KEYBRD,*) VD,VC,VS,VB
*IF BATCH
WRITE (KONSOL,1001) VD,VC,VS,VB
FORMAT(1P4G13.3)
1001
*ENDIF
VDR=VD-VB
VSB=VS-VB
VCG=VG-VB
IF (KPHIS.EQ.1) PHNREF=PHNREF-VB
0
0.....CHECK IF RE-INITIALIZE
IF (KINIT.EQ.0) [
WRITE (KONSOL,1005)
FORMAT('Re-initialize the potential (Yes=f7/No=f8) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
FORMAT(01)
IF (KANSUR.EQ.KYES) KINIT=1
]
0
0.....CHECK IF RE-DEFINE ITERATION PARAMETERS
IF (KPITR.EQ.0) [
WRITE (KONSOL,1007)
FORMAT('With some iteration parameters (Yes=f7/No=f6) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
IF (KANSUR.NE.KYES) KPITR=1
]
0
0.....GET 1-D ITERATION PARAMETERS
KSOLV=1
IF ((KINIT.EQ.1).AND.(KPITR.EQ.1)) [
WRITE (KONSOL,1011)
FORMAT('Absolute resolution of 1-D iteration (nV's) ? -')
READ (KEYBRD,*) ATOL1
*IF BATCH
WRITE (KONSOL,1001) ATOL1
*ENDIF
1011
ATOL1=ABS(ATOL1+1.0(EXP)-3)
]
0
0.....GET 2-D ITERATION PARAMETERS
IF (KPITR.EQ.1) [
WRITE (KONSOL,1012)
FORMAT('Absolute resolution of 2-D solution (nV's) ? -')
1012
```

-127-

File: 4SOLVE

```
READ (KEYBRD,*) ATOL2
*IF BATCH
WRITE (KONSOL,1001) ATOL2
*ENDIF
ATOL2=ABS(ATOL2+1.0(EXP)-3)
WRITE (KONSOL,1020)
FORMAT('Relaxation factor (1<=x(2, -1.7) ? -')
READ (KEYBRD,*) RELAX2
*IF BATCH
WRITE (KONSOL,1001) RELAX2
*ENDIF
RELAX1=RELAX2
WRITE (KONSOL,1040)
FORMAT('Maximum count of 2-D iterations ? -')
READ (KEYBRD,*) KMAX2
*IF BATCH
WRITE (KONSOL,1002) KMAX2
FORMAT(13)
1002
*ENDIF
WRITE (KONSOL,1030)
FORMAT('Convergence information per 2-D iteration',^
(Yes=f7/No=f8) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
IF (KANSUR.EQ.KYES) KINSG2=2
ELSE
KINSG2=0
]
0
0.....CHECK IF TO SEARCH FOR A SPECIFIC SURFACE POTENTIAL
IF (KPHIS.EQ.0) [
WRITE (KONSOL,1050)
FORMAT('Search for specific surface potential ',^
(Yes=f7/No=f8) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
IF (KANSUR.EQ.KYES) KPHIS=1
]
0
0.....GET SEARCHING PARAMETERS
IF (KPHIS.EQ.1) [
IF (KBIAS.NE.0) [
WRITE (KONSOL,1055)
FORMAT('With some searching parameters ',^
(Yes=f7/No=f8) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
IF (KANSUR.EQ.KYES) KNEU=0
ELSE
KNEU=1
]
IF (KNEU.EQ.1) [
WRITE (KONSOL,1060)
FORMAT('Target surface potential value ',^
(reference to VBI) ? -')
READ (KEYBRD,*) PHNREF
*IF BATCH
WRITE (KONSOL,1001) PHNREF
*ENDIF
PHNREF=PHNREF-VB
WRITE (KONSOL,1070)
FORMAT('Iterate which bias (D=Vd,C=Vg,S=Vs,B=Vb) ? -')
READ (KEYBRD,2000) KANSUR
*IF BATCH
WRITE (KONSOL,2000) KANSUR
*ENDIF
2000
DO K=1,4; IF (KANSUR.EQ.NARVLT(K)) KBIAS=K
KBIAS=MIN(4,MAX(1,KBIAS))
WRITE (KONSOL,1080)
FORMAT('First try value ? -')
READ (KEYBRD,*) VTRY
*IF BATCH
WRITE (KONSOL,1001) VTRY
*ENDIF
1080
WRITE (KONSOL,1090)
```

-128-

File: 4SOLVE

```

1090      FORMAT("Searching tolerance (nV's) ? _")
        READ (KEYBRD,0) ATOLS
*IF BATCH      WRITE (KONSOL,1001) ATOLS
*ENDIF
        ATOLS=ABS(ATOLS+1.0<EXP>-3)
    ]
0.....INITIALIZE POTENTIAL BASED ON 1-D SOLUTION
    IF (KINIT.EQ.1) CALL INITL (1)
    IF (KINIT.EQ.1) [
        CALL INITL (1)
        WRITE (KONSOL,2010) KBELL
        READ (KEYBRD,2000) KANSUR
*IF BATCH      WRITE (KONSOL,2000) KANSUR
*ENDIF
        IF (KANSUR.EQ.KYES) RETURN
        FORMAT(R1,"
2010      "Check auto-initialization results (Yes=f7/No=f8) ? _")
    ]
0.....ALLOW USER TO MODIFY INITIALIZATION
    IF (KSOLV.EQ.1) KSOLV=2
    IF (KSOLV.EQ.1) [
        KSOLV=2
        WRITE (KONSOL,2020)
        READ (KEYBRD,2000) KANSUR
*IF BATCH      WRITE (KONSOL,2000) KANSUR
*ENDIF
        FORMAT("Modify initial solution (Yes=f7/No=f8) ? _")
        IF (KANSUR.EQ.KYES) [
            CALL INHOD
            WRITE (KONSOL,2030)
            READ (KEYBRD,2000) KANSUR
            IF (KANSUR.EQ.KYES) RETURN
            FORMAT("Check modified initial solution (Yes=f7/No=f8) ? _")
        ]
    ]
0.....END OF INITIALIZATION
    IF (KSOLV.EQ.2) [
        KSOLV=3
        WRITE (KONSOL,2040) (NANSTR,K=1,24)
        FORMAT(/,12A2,5X,"END OF INITIALIZATION",5X,12A2/)
    ]
0.....2-D ITERATION
    REPEAT [
        IF (KSOLV.EQ.3) [
            IF (KNAX2.NE.0) [
                CALL POSSN
            ]
        ]
0.....SEARCHING LOOP
        IF (KPNIS.NE.0) [
            CALL PHAIN (1,PHIS,LPNIS)
            KOUNT=0
            WHILE ((ABS(PHIS-PHSREF).GT.ATOL2).AND.^
                (KOUNT.LT.ITRMAX)) [
                IF (KOUNT.EQ.0) [
                    IF (PHIS.GT.PHSREF) SGH=-1.0<EXP>0
                    ELSE
                        SGH= 1.0<EXP>0
                    DVTRY=SGH*VT300K
                    IF ((KBIAS.EQ.1).OR.(KBIAS.EQ.4))
                        DVTRY=-DVTRY
                ]
                IF (ABS(DVTRY).GT.ATOLS) [
                    XPHS=XPOS(LPNIS)+1.0<EXP>4
                    DPNS=PHIS-PHSREF
                    WRITE (KONSOL,2050)PHIS,XPHS,LPNIS,DPNS,DVTRY
                    FORMAT("PHIS =",F7.3,"
2050      "at K =",F7.3,"uh (*,12,*), Dphs=",^
                        F7.3,"
                        Dv=",F7.3)
                    IF(KBIAS.EQ.1)[ VDB=VDB+DVTRY; VBIAS=VDB+VB ]
                    IF(KBIAS.EQ.2)[ VCB=VCB+DVTRY; VBIAS=VCB+VB ]
                    IF(KBIAS.EQ.3)[ VSB=VSB+DVTRY; VBIAS=VSB+VB ]
                    IF(KBIAS.EQ.4)[

```

File: 4SOLVE

```

        VDB=VDB-DVTRY
        VCB=VCB-DVTRY
        VSB=VSB-DVTRY
        PHSREF=PHSREF-DVTRY
        VB=VB+DVTRY
        VBIAS=VB
    ]
    WRITE (KONSOL,0000) NANVLT(KBIAS),VBIAS,^
        (NANSTR,K=1,31)
    FORMAT("Try V",A1," = ",F7.3,3I2)
    PHSOLD=PHIS
    KOUNT=KOUNT+1
    CALL INITL (0)
    CALL POSSN
    CALL PHAIN (1,PHIS,LPNIS)
    DVTRY=-DVTRY+(PHSREF-PHIS)/(PHSOLD-PHIS)
    ]
    ]
    ELSE KOUNT=ITRMAX
    ]
    ]
0.....CHECK RESULTS
    CALL CHECK
    KSOLV=4
*IF BATCH      WRITE (KONSOL,3030) KBELL
3030      FORMAT (R1,"_")
*ENDIF
3031      WRITE (KONSOL,3031)
        FORMAT("Check results (Yes=f7/No=f8) ? _")
        READ (KEYBRD,2000) KANSUR
        IF (KANSUR.EQ.KYES) RETURN
    ]
    ]
    ELSE [
        KSOLV=5
        KGO2=0
    ]
    ]
0.....CHECK IF MORE 2-D ITERATION
    IF (KSOLV.EQ.4) [
        KSOLV=3
        WRITE (KONSOL,3040)
        FORMAT("More iterations (Yes=f7/No=f8) ? _")
        READ (KEYBRD,2000) KANSUR
*IF BATCH      WRITE (KONSOL,2000) KANSUR
*ENDIF
        IF (KANSUR.EQ.KYES) KGO2=1
        ELSE
            KGO2=0
        ]
    ]
    ] UNTIL (KGO2.EQ.0)
    WRITE (KONSOL,3050) (NANSTR,K=1,20)
    FORMAT(/,9A2,A1,5X,"END OF TWO DIMENSIONAL SOLUTION",5X,9A2,A1/)
0.....CHECK IF ANY MORE BIAS POINTS
    KSOLV=0
    KINIT=0
    KPITR=0
    IF (KPHIS.EQ.1) PHSREF=PHSREF+VB
    WRITE (KONSOL,4000)
    FORMAT("Another bias point (Yes=f7/No=f8) ? _")
    READ (KEYBRD,2000) KANSUR
*IF BATCH      WRITE (KONSOL,2000) KANSUR
*ENDIF
        IF (KANSUR.EQ.KYES) KGO=1
        ELSE
            KGO=0
        ] UNTIL (KGO.EQ.0)
    ]
0.....DONE
    KSOLV=0
    KBIAS=0
    KPHIS=0
    RETURN
    END

```

File: SSETPA

```
*CALL TUNDEFN
SUBROUTINE SETPA
0
0   SETUP MESH AND DOPING PROFILES
0
0 *CALL TCONMH
0
0 ..... SET UP MESH
0      IF (NEUNSH.EQ.1) CALL TRESH
0
0 ..... GENERATE DOPING PROFILE IF MESH CHANGED OR NEW PROFILE DEFINED
0      IF ((NEUDOP.EQ.1).OR.(NEUNSH.EQ.1)) [
0          IF (K SUPRN.EQ.0) CALL DDPNG
0          ELSE [
0              IF (K READ.EQ.0) CALL DOPB1
0              ELSE      CALL REDF2
0          ]
0      ]
0
0 ..... DONE
0      RETURN
0      END
```

File: SIFERR

```
*CALL TUNDEFN
SUBROUTINE IFERR (KFLAG,KERR,HANBUF,KRET)
0
0   HANDLE THE ERRORS IN FILE OPEN/CLOSE
0
0 *CALL TCONMH
0
0   DIMENSION HANBUF(1)
0
0   DATA KYES/2HY /
0
0 ..... IF KFLAG=1, ERROR IN OPEN FILE:
0 ..... ISSUE WARNING MESSAGE, SET REOPEN FLAG
0 ..... IF (KFLAG.EQ.1) [
0          WRITE (KONSOL,1000) KERR,(HANBUF(K),K=1,3),HANBUF(5),HANBUF(6)
0          READ  (KEYBRD,2000) KANSUR
0          IF (KANSUR.EQ.KYES) KRET=1
0          ELSE      KRET=0
0          FORMAT("Open error ",I3," in file ",J2,"1",A2,"1",A2,"
0              "1 Another try (Yes=f7/No=f8) ? _")
0          ]
0
0 ..... ELSE, ERROR IN CLOSE FILE: ISSUE WARNING MESSAGE
0 ..... ELSE [
0          WRITE (KONSOL,3000) KERR,(HANBUF(K),K=1,3),HANBUF(5),HANBUF(6)
0          ]
0          FORMAT("Error ",I3," in closing file ",J2,"1",A2,"1",A2)
0
0 ..... DONE
0      RETURN
0      END
```



```

*CALL TDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
FUNCTION FUNC (X,Y)
0
INTER-POLATE THE FUNCTIONAL VALUE OF PLOTTING ARRAY
0
F(1)=Z(NX1,NY1)          F(2)=Z(NX1+1,NY1)
F(3)=Z(NX1,NY1+1)        F(4)=Z(NX1+1,NY1+1)
0
*CALL TENA
*CALL TCONHN
0
DIMENSION F(4)
0
..... STATEMENT FUNCTIONS
ZUPPR(X)=(X-N1)*(F(2)-F(1))/DX+F(1)
ZDOWN(X)=(X-N1)*(F(4)-F(3))/DX+F(3)
ZLEFT(Y)=(Y-N1)*(F(3)-F(1))/DY+F(1)
ZRITE(Y)=(Y-N1)*(F(4)-F(2))/DY+F(2)
0
..... DEFINE FOUR CORNERS
NX1=MAX(LOCX(K),1)      X1=XPOS(NX1)
NY1=MAX(LOCY(Y),1)      Y1=YPOS(NY1)
IF (NX1.LT.NXMAX) DX=DELX(NX1)
ELSE                      DX=0.0<EXP>0
X2=N1+DX
IF (NY1.LT.NYMAX) DY=DELY(NY1)
ELSE                      DY=0.0<EXP>0
Y2=N1+DY
0
..... GET FUNCTION VALUES AT THE CORNERS
DO K=1,4; F(K)=Z(NX1,NY1)
IF (NX1.LT.NXMAX)      F(2)=Z(NX1+1,NY1)
IF (NY1.LT.NYMAX)      F(3)=Z(NX1,NY1+1)
IF ((NX1.LT.NXMAX).AND.(NY1.LT.NYMAX)) F(4)=Z(NX1+1,NY1+1)
ELSE [
IF (NX1.LT.NXMAX)      F(4)=F(2)
IF (NY1.LT.NYMAX)      F(4)=F(3)
]
0
..... INTERPOLATE THE FUNCTION VALUE AT (X,Y)
IF ((DX.NE.0.0<EXP>0).AND.(DY.NE.0.0<EXP>0)) [
FUNC=0.5<EXP>0*((X-N1)*(ZRITE(Y)-ZLEFT(Y))/DX+ZLEFT(Y)+
(Y-N1)*(ZDOWN(X)-ZUPPR(X))/DY+ZUPPR(X))
]
ELSE [
IF (DX.NE.0.0<EXP>0) FUNC=ZUPPR(X)
IF (DY.NE.0.0<EXP>0) FUNC=ZLEFT(Y)
]
0
..... DONE
RETURN
END

```

```

*CALL TDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE TMESH
0
SET-UP MESH AND CALCULATE RELATED COEFFICIENTS
0
*CALL TENA
*CALL TCONHN
0
..... EQUIVALENCE EMA ARRAYS INTO ONE-DIMENSIONAL ARRAYS
DIMENSION ODCNSI(1),ODCSSI(1),ODCE9I(1),ODCWSI(1),ODDOME(1),^
ODCMOX(1),ODCSOX(1),ODCEOX(1),ODCWOX(1),^
ODCNOI(1),ODCSOI(1)
EQUIVALENCE (ODCHSI(1),CHORTH(1,1)),(ODCSSI(1),CSOUTH(1,1)),^
(ODCE9I(1),CEAST(1,1)),(ODCWSI(1),CWEST(1,1)),^
(ODDOME(1),DOME(1,1)),^
(ODCMOX(1),CMOX(1,1)),(ODCSOX(1),CSOX(1,1)),^
(ODCEOX(1),CEOX(1,1)),(ODCWOX(1),CWOX(1,1)),^
(ODCNOI(1),CNOXI(1,1)),(ODCSOI(1),CSOXI(1,1))
0
..... ROCK'S CONSTANT
DATA DELTAX/0.1<EXP>0/, DELTAY/0.05<EXP>0/
0
..... SILICON MESH = 50X40
NXMAX=50
NYMAX=40
0
..... OXIDE MESH = 50X(2+1) [ SHARES INTERFACE WITH SILICON MESH ]
IF ((TOXO.NE.0.0<EXP>0).OR.(TOXI.NE.0.0<EXP>0)) NOXIDE=2
ELSE
NOXIDE=0
0
..... ALLOCATE SOURCE AND DRAIN DOMAINS
XDIFF=XSOURCE-XDRAIN
NXRX1=NXMAX+1
IF (XDIFF.NE.0.0<EXP>0) [
NDIFF=10
NS=NDIFF*(XSOURCE/XDIFF)
NSRCO=NS+1
NSRC1=NSRCO
ND=NDIFF-NS
NDRNO=NXMAX-ND
NDRN1=NDRNO
]
ELSE [
NDIFF=0
NSRCO=0
NSRC1=1
NDRNO=NXRX1
NDRN1=NXMAX
]
0
..... ROCK'S ALGORITHM APPLIED ONLY TO EVEN X-MESHES IN DRAIN CHANNEL REGION
NCHANL=NINO(NDRN1-NSRC1,NXMAX)
NHALF=NCHANL/2
IF ((NHALF*2).NE.NCHANL) [
NCHANL=NCHANL-1
NDRN1=NDRN1-1
NDRNO=NDRNO-1
NXMAX=NXMAX-1
]
0
..... DETERMINE X-MESH SIZES IN DRAIN CHANNEL REGION (SYMMETRICAL)
CALL TROCK (0.5<EXP>0*NCHANL,NHALF,NSRC1,1)
NSTOP=NSRC1+NHALF-1
IMAGE=NDRN1
DO K=NSRC1,NSTOP (
IMAGE=IMAGE-1
DELX(IMAGE)=DELX(K)
]
0
..... DETERMINE X-MESH SIZES IN SOURCE AND DRAIN DOMAINS
IF (NSRCO.GT.1) CALL TROCK (NSOURCE,NS,NSRCO-1,-1)
IF (NDRNO.LT.NXMAX) CALL TROCK (XDRAIN,ND,NDRNO,1)
0
..... DEFINE ARRAY XPOS, X-ORIGIN AT THE LEFT EDGE OF DRAIN CHANNEL REGION
XPOS(NSRC1)=0.0<EXP>0
NS1=NSRC1+1
NS2=NSRC1-1
ZXXX=0.0<EXP>0 DO K=NS1,NXMAX [ ZXXX=ZXXX+DELX(K-1); XPOS(K)=ZXXX ]
IF (NSRCO.NE.0) [
ZXXX=0.0<EXP>0
FOR (K=NS2; K=1) K=K-1 [ ZXXX=ZXXX-DELX(K); XPOS(K)=ZXXX ]
]

```

```

0
0..... GET ALL LOCATION INDICES
NGATE0=LOCK(NGATE0)
NGATE1=LOCK(NGATE1)
IF (NGATE0.EQ.0) [ IF (NGATE1.NE.0) NGATE0=1 ]
ELSE [ IF (NGATE0.NE.XPOS(NGATE0)) NGATE0=NGATE0+1 ]
HX0=LOCK(HX0)
HX1=LOCK(HX1)
IF (HX0.EQ.0) [ IF (HX1.NE.0) HX0=1 ]
ELSE [ IF (HX0.NE.XPOS(HX0)) HX0=HX0+1 ]
IF (XSUPRN.EQ.0) [
HIMPL0=LOCK(HIMPL0)
HIMPL1=LOCK(HIMPL1)
IF (HIMPL0.EQ.0) [ IF (HIMPL1.NE.0) HIMPL0=1 ]
ELSE [ IF (HIMPL0.NE.XPOS(HIMPL0)) HIMPL0=HIMPL0+1 ]
]
]
0..... CALCULATE X-COEFFICIENT ARRAYS
OVRDX=1.0<EXP>0/DELX(1)
Z(1,1)=OVRDX*OVRDX
Z(1,2)=0.0<EXP>0
NXM1=NXMAX-1
DO K=2,NXM1 [
OVRDX1=OVRDX
OVRDX=1.0<EXP>0/DELX(K)
Z(K,1)=OVRDX*OVRDX
Z(K,2)=OVRDX*OVRDX1
]
Z(NXMAX,1)=0.0<EXP>0
Z(NXMAX,2)=Z(NXM1,1)
0..... DETERMINE Y-MESH
CALL TROCK (YMAX,NYMAX-1,1,2)
IF (KSUPRN.EQ.0) XJ=ANANI(KJCT(1),KJCT(2),KJCT(3))
ELSE XJ=0.3<EXP>-4
IF (XJ.GT.0.0<EXP>0) [
Y10=DELY(1)
KS=MIN(10,NYMAX)
DO K=2,KS [ Y10=Y10+DELY(K)
IF (Y10.GT.XJ) [
CALL TROCK (XJ,10,1,2)
NYM1=NYMAX-1
NYMESH=NYM1-10
YMESH=(YMAX-XJ)/NYMESH
DO K=11,NYM1 [ DELY(K)=YMESH
]
]
]
0..... DEFINE ARRAY YPOS, Y-ORIGIN AT INTERFACE
YPOS(1)=0.0<EXP>0
ZXXX=0.0<EXP>0 DO K=2,NYMAX [ ZXXX=ZXXX+DELY(K-1) YPOS(K)=ZXXX ]
0..... CALCULATE Y-COEFFICIENT ARRAYS
OVRDY=1.0<EXP>0/DELY(1)
Z(1,3)=OVRDY*OVRDY
Z(1,4)=0.0<EXP>0
NYM1=NYMAX-1
DO K=2,NYM1 [
OVRDY1=OVRDY
OVRDY=1.0<EXP>0/DELY(K)
Z(K,3)=OVRDY*OVRDY
Z(K,4)=OVRDY*OVRDY1
]
Z(NYMAX,3)=0.0<EXP>0
Z(NYMAX,4)=Z(NYM1,3)
0..... DEFINE OXIDE MESH
DO K=1,NXMAX [ DELOX(K,1)=0.0<EXP>0; DELOX(K,2)=0.0<EXP>0 ] 0 INIT
DELOY=DELY(1)/(1.0<EXP>0-DELTA) 0 ROCK'S FORMULA
EONES1=EPS102/EPST 0 DIELECTRIC
TOX0=TOX0+EOXES1 TOXN1=TOX1+EOXES1
DEL0=ANINI(DELVOX,TOX0); DELS1=ANINI(DELVOX,TOXN1)
DELTO=TOX0-DEL0; DELTI=TOXN1-DELS1
NSTOP=NOX0+NOXR 0 SOURCE SIDE
NSTOP=LOCK(NSTOP)
IF (NSTOP.GE.1)
DO K=1,NSTOP [
DELOX(K,1)=DEL0
DELOX(K,2)=DELTI
]
]

```

```

IF ((NOX0.LE.NOX1).AND.(NOX1.NE.0)) 0 MIDDLE PART
DO K=NOX0,NOX1 [
DELOX(K,1)=DEL0
DELOX(K,2)=DELTO
]
XSTR1=NOX1+NOXR 0 DRAIN SIDE
HSTR1=LOCK(XSTR1)
IF (HSTR1.EQ.0) HSTR1=1
ELSE IF (HSTR1.NE.LOCK(XSTR1)) HSTR1=HSTR1+1
IF (HSTR1.LE.NXMAX) [
DO K=HSTR1,NXMAX [
DELOX(K,1)=DELS1
DELOX(K,2)=DELTI
]
]
IF (NOXR.NE.0.0<EXP>0) [ 0 THE RAMPS
SLOPE=(TOXN1-TOX0)/NOXR
M1=NSTOP+1 0 SOURCE RAMP
M2=NOX0-1
IF ((M2.GE.M1).AND.(M1.NE.0)) [
NR=NSTOP
DO K=M1,M2 [
TOXN=TOXN1-SLOPE*(XPOS(K)-NR)
DELS=ANINI(TOXX,DELOY)
DELOX(K,1)=DELS
DELOX(K,2)=TOXN-DELS
]
]
M1=NOX1+1 0 DRAIN RAMP
M2=HSTR1-1
IF ((M2.GE.M1).AND.(M1.NE.0)) [
NR=NOX1
DO K=M1,M2 [
TOXN=TOX0+SLOPE*(XPOS(K)-NR)
DELS=ANINI(TOXX,DELOY)
DELOX(K,1)=DELS; DELOX(K,2)=TOXN-DELS
]
]
]
0..... CALCULATE Y-COEFFICIENT ARRAYS ASSOCIATED WITH OXIDE
ESTIOX=EPS1/EPST02
OVRDY=1.0<EXP>0/DELY(1)
DO K=1,NXMAX [
DARG=DELOX(K,1)
IF (DARG.NE.0.0<EXP>0) OVRDY1=1.0<EXP>0/DARG
ELSE OVRDY1=0.0<EXP>0
DARG=DELOX(K,2)
IF (DARG.NE.0.0<EXP>0) OVRDY2=1.0<EXP>0/DARG
ELSE OVRDY2=0.0<EXP>0
Z(K,5)=ESTIOX*OVRDY1*OVRDY1
Z(K,6)=OVRDY1*OVRDY2
Z(K,7)=OVRDY2*OVRDY2
Z(K,8)=EOXES1*OVRDY1*OVRDY
]
0..... CALCULATE POISSON EQUATION COEFFICIENT ARRAYS
GONEPS=0/EPST
DO KX=1,NXMAX [
CE=Z(KX,1)
CU=Z(KX,2)
]
0..... INSIDE SILICON
DO KY=1,NYMAX [
CS=Z(KY,3)
IF (KY.EQ.1) CN=Z(KX,8)
ELSE CN=Z(KY,4)
OMEGA=1.0<EXP>0/(CE+CU+CS+CN)
]
0 PERFORM SUBSCRIPT CALCULATION EXACTLY ONCE: array(I,J) -> array(K)
ONE-DIMENSIONAL OFFSET VALUE: K=(J-1)*50+I
KMY=(KY-1)*50+KX
ODDOME(KMY)=0ONEPS*OMEGA
ODCES(KMY)=CE*OMEGA
ODCUS(KMY)=CU*OMEGA
ODCBS(KMY)=CS*OMEGA
ODCMB(KMY)=CN*OMEGA
OMEGA=1.0<EXP>0/(CH+CS)
IF (KY.EQ.1) [
]
]

```



```

*CALL TUNDEFM
*IF NP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE TPRNT (NX1,NX2,NY1,NY2,X1,X2,Y1,Y2,Z1,Z2,KDISP,KELEC,KFELD)
0
PRINT THE RESULT
*CALL TEMA
*CALL TCOMM
0
DIMENSION MSGDSP(10,4), MSGEAM(4,2), MSGFLD(6,4)
0
DATA LUPRT/6/, LENDSP/10/, MUNDSP/4/, ^
MSGDSP/2HD,2HP1,2HG,2H C,2HW,2HCE,2HNT,2HRA,2HTI,2HON,^
2HFR,2HEC,2H C,2HAR,2HTI,2HEA,2H P,2HRO,2HF1,2HLE,^
2HP0,2HEL,2HD,2HD1,2HSR,2HRI,2HU,2HTI,2HON,2H ^,^
MSGEAM/2H01,2H02,2H1,2H1A,2HL,2H P,2HRO,2HF1,2HLE,2H ^,^
2H01,2H02,2H ^,2H ^,^
LENFLD/6/, MUNFLD/4/, ^
MSGFLD/2HX,2Hco,2Hnp,2Hon,2Hn,2Ht, ^
2HY,2Hco,2Hnp,2Hon,2Hn,2Ht, ^
2Hra,2Hti,2Ho,2Hof,2H X,2HY,^
2Hna,2Hna,2Hti,2Hud,2Hn,2H ^,^
DATA NAMBLK/2H ^, NAMSTR/2H00/, NAMDOT/2H../, NCPAGE/9/
0
THE TITLE
WRITE (LUPRT,3000) (NAMSTR,K=1,60)
3000 FORMAT(29A2,A1,4X,"TUIST",4X,29A2,A1)
0
FUNCTION NAME
WRITE (LUPRT,4000) NAMDOT,(MSGDSP(K,KDISP),K=1,LENDSP),^
(MSGEAM(K,KELEC),K=1,4),(NAMDOT,K=1,41)
4000 FORMAT(A2,2X,10A2,2X," referring to ",4A2,1X,41A2)
0
IF (KDISP.EQ.3) [
WRITE (LUPRT,4010) NAMDOT,(MSGFLD(K,KFELD),K=1,LENFLD)
4010 FORMAT(A2,3A2,"( ",6A2," )")
0
]
0
BASIS VOLTAGES
WRITE (LUPRT,4020) NAMDOT,VDB,VGB,VSB,(NAMDOT,K=1,42)
4020 FORMAT(A2,3(1PG10.2),"(VDB, VGB, VSB)",41A2,A1)
0
DOMAIN DEFINITIONS
WRITE (LUPRT,5010) Z1,Z2,(NAMDOT,K=1,39)
5010 FORMAT(2X,2(1PG10.2),10X,"(Zmin,Zmax) estimated ",39A2,A1)
0
9 COLUMNS PER PAGE
MPAGE=(NX2-NX1)/NCPAGE
IF ((NX2-NX1).NE.(MPAGE*NCPAGE)) MPAGE=MPAGE+1
N2=NX1-1
NROW=NY2-NY1+1
DO KP=1,MPAGE [
N1=N2+1
N2=N1+(N2+MPAGE,NX2)
NCOL=N2-N1+1
0
]
BLANK LINE BETWEEN EACH PAGE, PRECEDE EACH BY COUNTS OF COLUMNS AND ROWS
WRITE (LUPRT,6000) NCOL,NROW,KP,(NAMDOT,K=1,39)
6000 FORMAT(7,2X,15,110,9X,"(column,row) on Page ",13,2X,39A2)
0
FOLLOWED BY X-COORDINATES
WRITE (LUPRT,6003) (K,K=N1,N2)
WRITE (LUPRT,6010) (XPOS(K),K=N1,N2)
6003 FORMAT(11X,9(19,4X))
6010 FORMAT(2X,"V(CM)X(CH)",2X,9(1PG9.2,4X))
0
DUMP THE NUMBERS
DO KY=NY1,NY2 [
WRITE (LUPRT,7000) KY,YPOS(KY),(Z(K,KY),K=N1,N2)
7000 FORMAT(12,1PG9.2,2X,9(1PG13.5))
0
]
0
DONE
RETURN
END

```

```

*CALL TUNDEFM
*IF NP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE TRACE (KCCB,KDCB,N,M,L,PLINE)
0
TRACE OUT A CONTOUR LINE
KCCB -> GRAPHIC CONTROL BLOCK
M -> STARTING X-INDEX
N -> STARTING Y-INDEX
LL -> LINE INDEX 1 0 -> STARTING AT Y-DIRECTION
(0 -> STARTING AT X-DIRECTION)
PLINE-> LINE VALUE
0
(NX,NY) = STARTING POSITION -> FINAL POSITION
KTRC = TRACING FLAG 1 -> 1ST SEGMENT
KDIR = GOING DIRECTION 2 -> NOT 1ST SEGMENT
0 -> END OF LINE
IF (POTS(NX,NY).EQ.PLINE) 1
1 = BETWEEN (NX+1,NY) AND (NX+1,NY-1)
2 (NX+1,NY-1) (NX,NY-1)
3 (NX,NY-1) (NX-1,NY-1)
4 (NX-1,NY-1) (NX-1,NY)
5 (NX-1,NY) (NX-1,NY+1)
6 (NX-1,NY+1) (NX,NY+1)
7 (NX,NY+1) (NX+1,NY+1)
8 (NX+1,NY+1) (NX+1,NY)
IF (POTS(NX,NY).NE.PLINE) 1
1 = BETWEEN (NX,NY) AND (NX+1,NY), FROM +NY TO -NY (A)
2 (NX,NY) (NX,NY-1), +NX -NX (B)
3 (NX,NY) (NX-1,NY), -NY +NY (C)
4 (NX,NY) (NX,NY+1), -NX +NX (D)
5 (NX,NY) (NX+1,NY), -NY +NY (E)
6 (NX,NY) (NX,NY+1), +NX -NX (F)
7 (NX,NY) (NX-1,NY), +NY -NY (G)
8 (NX,NY) (NX,NY-1), -NX +NX (H)
0
(XP,YP) = COORDINATE
POTS(N,M) = DATA ARRAY
XPOS (N) = X-POSITION ARRAY, DELX(N) = X-MESH SIZE ARRAY
YPOS (N) = Y-POSITION ARRAY, DELY(N) = Y-MESH SIZE ARRAY
0
1 <= M <= NMAX, 1 <= N <= NYMAX, 1 <= LL <= NLMAX
*CALL TEMA
*CALL TCOMM
0
PLOTTING PARAMETERS
DIMENSION KCCB(1), KDCB(1), LBUF (3)
DIMENSION KCRCH(8),KN(9),KM(9)
0
DATA KN/1, 1, 0,-1,-1,-1,0,1,1/, KM/0,-1,-1,-1, 0, 1,1,1,0/
DATA MSEC/0/, NCR/2HCC/, NAMX/2HX ^, NARY/2HY ^
0
SET FIRST SET OF INDICES
NX=M
NY=N
KTRC=1
LL=L
IF (LL.GT.0) [ N1=N; N1=N+1; KDIR=4; CALL LNMRK (N,M,LL) ]
ELSE [ N1=N+1; N1=N; KDIR=5; CALL LNMRK (N,M,LL) ]
0
]
MOVE TO THE FIRST POINT
POTO=POTS(NX,NY)
XP=XPOS(NX)
YP=YPOS(NY)
IF (PLINE.NE.POTO) [
POTI=POTS(N1,N1)
IF (POTO.NE.POTI)
IF (NX.NE.N1) XP=XP+DELX(NX)*(PLINE-POTO)/(POTI-POTO)
ELSE YP=YP+DELY(NY)*(PLINE-POTO)/(POTI-POTO)
ELSE IF (NY.NE.N1) XP=XP+0.5*(XP+0)*DELX(NX)
ELSE YP=YP+0.5*(YP+0)*DELY(NY)
]
CALL MOVE (KCCB,XP,-YP)
XPN=XP
YPN=YP

```


File: STRACE

```
0.....LOAD INDICES AND PLOT THE POINT
      NX=NO
      NY=NO
      ]
      NPTS=NPTS+1
      CALL DRAW (KCCB,XP,-YP)
      ]
0.....END OF LINE
      ELSE KEND=2
      ] UNTIL (KEND.NE.0)
0.....LABEL
      IF (KTRC.EQ.1) [
          CALL CODE1 WRITE (LBUF,1000) PLINE
          FORMAT (F6.2)
          CALL LORG (KCCB,9)
          CALL GFONT (KCCB,6HFONT2 ,NSEC,MCR,KDCB)
          NS=1
          NC=6
          CALL GTEXT (KCCB,LBUF,NS,NC,KDCB)
          CALL GFONT (KCCB,0,0,0,KDCB)
      ]
0.....END OF 1ST SEGMENT
      IF ((KTRC.EQ.1).AND.(KEND.EQ.2).AND.(L.LT.0)) [
          CALL MOVE (KCCB,XPN,-YPH)
          NX=N
          NY=N
          LL=-L
          KDIR=1
      ]
      ELSE KTRC=KTRC+1
0.....END OF 2ND SEGMENT
      KTRC=KTRC+1
      ] UNTIL (KTRC.GT.2)
      CALL PENUP (KCCB)
0.....DONE
      RETURN
      END
```

File: STSCAL

```
*CALL TDEFN
SUBROUTINE TSCAL (KCCB,XOHY,CHARN,CHITE,XLENG,YLENG)
0
0 SCALE CHARACTER SIZE
0
0 *CALL TCOMHH
DIMENSION KCCB(192)
0
0 DATA ASPEC/0.7<EXP>0/, SLANT/0.0<EXP>0/
0
0 CHECK PLOTTING SURFACE
      IF (XOHY.GT.1.0<EXP>0) [
          UMRGN=100.0<EXP>0/6.0<EXP>0
          DMRGN=UMRGN/0.6<EXP>0
          BMRGN=XOHY*20.0<EXP>0
          FRMGN=BMRGN
          YLENG=100.0<EXP>0-UMRGN-DMRGN
          XLENG=XOHY*100.0<EXP>0-DMRGN-FMRGN
      ]
      ELSE [
          FRMGN=100.0<EXP>0/6.0<EXP>0
          BMRGN=FRMGN/0.6<EXP>0
          UMRGN=20.0<EXP>0/XOHY
          DMRGN=UMRGN
          YLENG=100.0<EXP>0/XOHY-UMRGN-DMRGN
          XLENG=100.0<EXP>0-DMRGN-FMRGN
      ]
0
0 ESTIMATE CHARACTER SIZE
      CN=XLENG/CHARN
      CY=YLENG/CHARN
      CHITE=AMIN(CN,CY)
      CWIDTH=ASPEC*CHITE
      CHITE=CWIDTH/ASPEC
      CALL CSIZE (KCCB,CHITE,ASPEC,SLANT,0)
0
0.....DONE
      RETURN
      END
```

File: &MBASE

```
*CALL TUDEFN
*IF HP1000
EMA (XYZ,0)
*ENDIF
SUBROUTINE MBASE (N,M,NB1,NB2)
*
* DETERMINE BARRIER WIDTH
*
*CALL TEMA
*CALL TCONHM
*
POTB=POTSI(N,M)
TMOVT=VT300K+VT300K
*
*..... FIND LEFT LIMIT OF THE BARRIER
POTX=POTSI(N-1,M)
NB1=M
WHILE ((NB1.GT.NSOURC).AND.((POTX-POTB).LE.TMOVT)) [
  NB1=NB1-1
  POTX=POTSI(NB1-1,M)
]
*
*..... FIND RIGHT LIMIT OF THE BARRIER
POTX=POTSI(N+1,M)
NB2=M
WHILE ((NB2.LT.NDRAIN).AND.((POTX-POTB).LE.TMOVT)) [
  NB2=NB2+1
  POTX=POTSI(NB2+1,M)
]
*
*..... DONE
RETURN
END
```

File: &MDEPL

```
*CALL TUDEFN
SUBROUTINE MDEPL (USO,US1,UDO,WD1)
*
* DETERMINE LATERAL SPANS OF SURFACE DEPLETION REGIONS
*
*CALL TCONHM
*
DATA A0/0.0631353<EXP>0/, A1/0.0013292<EXP>0/, A2/-0.01110777<EXP>0/
*
*..... GET JUNCTION DEPTH
IF (ABS(DDBE(3)).GT.1.0<EXP>0) [
  KJ=NSURF(3)
  ALPHAX=1.0<EXP>0/(ALPHB+ALPHA(3))
  PHIJO=PHIJ
*
*..... DEPLETION HOFBET
KDEPL=0
IF ((ABS(CSURF(1)).GT.0.0<EXP>0).AND.^
(SIGN(1.0<EXP>0,CSURF(1)).NE.TYPE)) [
  IF ((ABS(CSURF(1)).GT.1.0<EXP>0).AND.^
(ABS(CSURF(3)).GT.1.0<EXP>0))
  IF (ABS(CSURF(3)).GT.1.0<EXP>0)
  PHIJO=VT300K+ABS(ALOG(ABS((SIGN(CSUB,TYPE)+CSURF(3))/^
(SIGN(CSUB,TYPE)+CSURF(1))))))
  KOEPL=1
  PION2=2.0<EXP>0*ATAN2(1.0<EXP>0,1.0<EXP>0)
  TOKS1=TON0+EPSI/EP5I02
  TOKS12=TOKS1+TOKS1
  TOK2=TON0+TON0
  MO=PION2*(SQRT(KJ+KJ+TON2)-TON0)
*
*..... DETERMINE WIDTH OF SURFACE DEPLETION REGION
US1=SQRT(ALPHAX*ABS(VSB+PHIJ))/KJ
US1=KJ*(A0+A1*US1+A2*US1*US1)
WD1=SQRT(ALPHAX*ABS(VDB+PHIJ))/KJ
WD1=KJ*(A0+A1*WD1+A2*WD1*WD1)
US0=US1*ABS((SIGN(CSUB,TYPE)+CSURF(1))/(SIGN(CSUB,TYPE)+CSURF(3)))
WD0=WD1*ABS((SIGN(CSUB,TYPE)+CSURF(1))/(SIGN(CSUB,TYPE)+CSURF(3)))
IF (KDEPL.EQ.1) [
  IF ((VSB+PHIJO-VGB).GT.0.0<EXP>0) [
    UL=AMINI(MO,SQRT(ALPHAX*(VSB+PHIJO-VGB)+TOKS12)-TOKS1)
    VC=UL*UL/ALPHAX
    VSC0=UL*(TOKS1+TOKS1)/ALPHAX
    VSCOT=VC+VSC0
    EOX=((VSB+PHIJO-VGB)-VSCOT)/(TON0+UL*EPSI02/EP5I)
    PHIS=VGB+EOX*TON0+VSC0
    M2=UL/PION2+TON0
    M1=SQRT(M2*M2-TON2)
    US0=EPSI02*EOX/(0+ABS(CSTEP(3)))
  ]
  IF ((VDB+PHIJO-VGB).GT.0.0<EXP>0) [
    UL=AMINI(MO,SQRT(ALPHAX*(VDB+PHIJO-VGB)+TOKS12)-TOKS1)
    VC=UL*UL/ALPHAX
    VSC0=UL*(TOKS1+TOKS1)/ALPHAX
    VSCOT=VC+VSC0
    EOX=((VDB+PHIJO-VGB)-VSCOT)/(TON0+UL*EPSI02/EP5I)
    PHID=VGB+EOX*TON0+VSC0
    M2=UL/PION2+TON0
    M1=SQRT(M2*M2-TON2)
    WD0=EPSI02*EOX/(0+ABS(CSTEP(3)))
  ]
]
]
ELSE [
  US1=SQRT(ALPHB*ABS(VSB+PHIB+PHIB))
  WD1=SQRT(ALPHB*ABS(VDB+PHIB+PHIB))
  US0=US1*ABS((SIGN(CSUB,TYPE)+CSURF(1))/(SIGN(CSUB,TYPE)+CSURF(3)))
  WD0=WD1*ABS((SIGN(CSUB,TYPE)+CSURF(1))/(SIGN(CSUB,TYPE)+CSURF(3)))
]
*
*..... DONE
US0=AMAX(US0,0.0<EXP>0)
US1=AMAX(US1,0.0<EXP>0)
UDO=AMAX(UDO,0.0<EXP>0)
WD1=AMAX(WD1,0.0<EXP>0)
RETURN
END
```

REFERENCES

- [1] J.E.Lilienfeld, U.S. Patent No. 1,745,175, 1930.
- [2] O.Heil, British Patent No. 439,457, 1935.
- [3] W.Shockley and G.L.Pearson, "Modulation of Conductance of Thin Films of Semiconductors by Surface Charges," *Physical Review*, Vol.74, 1948, pp.232-233.
- [4] D.Kahng and M.M.Atalla, "Silicon-Silicon Dioxide Field Induced Surface Devices," IRE Solid-State Device Research Conference, Carnegie Inst. of Tech., Pittsburgh, Penn., 1960.
- [5] P.R.Gray and R.G.Meyer, *Analysis and Design of Analog Integrated Circuits*, Chapter 2, John Wiley & Sons, 1977.
- [6] E.S.Schlegel, "A Bibliography of Metal-Insulator-Semiconductor Studies," *IEEE Trans. Electron Devices*, Vol.ED-14, No.11, Nov. 1967, pp.728-749.
- [7] E.S.Schlegel, "Additional Bibliography of Metal-Insulator-Semiconductor Studies," *IEEE Trans. Electron Devices*, Vol.ED-15, No.12, Dec. 1968, pp.951-953.
- [8] W.Shockley, U.S. Patent No. 2,787,564, 1954.
- [9] J.F.Gibbons, "Ion Implantation in Semiconductors-Part I, Range Distribution Theory and Experiments," *Proc. IEEE*, Vol.56, No.3, March 1968, pp.295-319.

- [10] J.F.Gibbons, "Ion Implantation in Semiconductors-Part II, Damage, Production and Annealing," *Proc. IEEE*, Vol.60, No.9, Sept. 1972, pp.1062-1095.
- [11] L.W.Nagel, "SPICE2, A Computer Program to Simulate Semiconductor Circuits," *ERL Memorandum No.ERL-M520*, University of California, Berkeley, May 1975.
- [12] S.P.Fan, M.Y.Hsueh, A.R.Newton and D.O.Pederson, "MOTIS-C: A New Circuit Simulation for MOS LSI Circuits," *Proceedings of IEEE International Symposium, Circuits and Systems*, April 1977, pp.700-703.
- [13] A.R.Newton, "The Simulation of Large-Scale Integrated Circuits," *ERL Memorandum No.UCB/ERL-M78/52*, University of California, Berkeley, July 1978.
- [14] E.Khalily, "T.E.C.A.P.: A Automated Characterization System," *Technical Report No.5017-1*, Stanford Electronics Laboratories, Stanford University, March 1979.
- [15] A.Vladimirescu and S.Liu, "The Simulation of MOS Integrated Circuits Using SPICE2," *ERL Memorandum No. UCB/ERL M80/7*, University of California, Berkeley, Feb. 1980 (rev. Oct. 1980).
- [16] H.Shichman and D.A.Hodges, "Modeling and Simulation of Insulated-Gate Field-Effect Transistor Switching Circuits," *IEEE J. Solid-State Circuits*, Vol.SC-3, No.5, Sept. 1968, pp.285-289.
- [17] G.Baccarani, M.Rudan and G.Spadini, "Analytical IGFET Model Including Drift and Diffusion Currents," *Solid-State and Electron Devices*, Vol.2, No.2, March 1978, pp.62-68.

- [18] M.B.Barron, "Computer Aided Analysis of Insulated Gate Field Effect Transistors," *Technical Report No.5501-1*, Stanford Electronics Laboratories, Stanford University, Nov. 1969.
- [19] M.S.Mock, "A Two-Dimensional Mathematical Model of the Insulated-Gate Field-Effect Transistors," *Solid-State Electronics*, Vol.16, 1973, pp.601-609.
- [20] A.D.Sutherland, "A Two-Dimensional Computer Model for the Steady State Operation of MOSFET's," *Research and Development Technical Report, ECOM-75-1344-F Supplement*, Advanced Research Project Agency, Sept. 1977.
- [21] Y.A.El-Mansy and A.R.Boothroyd, "A New Approach to the Theory and Modeling of Insulated-Gate Field-Effect Transistors," *IEEE Trans. Electron Devices*, Vol.ED-24, No.3, March 1977, pp.241-253.
- [22] Y.A.El-Mansy and A.R.Boothroyd, "A Simple Two-dimensional Model for IGFET Operation in the Saturation Region," *ibid*, pp.254-262.
- [23] J.R.Brews, "Comments on 'A New Approach to the Theory and Modeling of IGFET's'," *IEEE Trans. Electron Devices*, Vol.ED-24, No.12, Dec. 1977, pp.1369-1370.
- [24] Y.A.El-Mansy, *Modelling of Insulated-Gate Field-Effect Transistors*, Ph.D. Dissertation, Carleton University, Ottawa, Canada, Nov. 1974.
- [25] Y.A.El-Mansy and A.R.Boothroyd, "MOS Device Modelling," preprint.
- [26] H.C.Pao and C.T.Sah, "Effects of Diffusion Current on Characteristics of Metal-Oxide (Insulator) Semiconductor Transistors," *Solid-State Electronics*, Vol.9, 1966, pp.927-937.

- [27] A.P.Gnädinger and H.E.Talley, "Quantum Mechanical Calculation of the Carrier Distribution and the Thickness of the Inversion Layer of a MOS Field-Effect Transistor," *Solid-State Electronics*, Vol.13, 1970, pp.1301-1309.
- [28] F.Stern, "Self-Consistent Results for N-type Si Inversion Layers," *Physical Review B*, Vol.5, No.12, 15 June 1972, pp.4891-4899.
- [29] J.A.Pals, "Experimental Verification of the Surface Quantization of an N-Type Inversion Layer of Silicon at 300 and 77°K," *Physical Review B*, Vol.5, No.10, 15 May 1972, pp.4208-4210.
- [30] K.von Klitzing, G.Landwehr and G.Dorda, "Shubnikov de Haas Oscillations in P-Type Inversion Layers on N-Type Silicon," *Solid-State Communications*, Vol.14, No.5, 1974, pp.387-393.
- [31] S.M.Sze, *Physics of Semiconductor Devices*, John Wiley & Sons, 1969.
- [32] R.Seiwatz and M.Green, "Space Charge Calculations for Semiconductors," *J. Applied Physics*, Vol.29, No.7, July 1958, pp.1034-1040.
- [33] T.I.Kamins and R.S.Muller, "Statistical Considerations in MOSFET Calculations," *Solid-State Electronics*, Vol.10, 1967, pp.423-431.
- [34] J.McDougall and E.C.Stoner, "The Computation of Fermi-Dirac Functions," *Trans. Royal Society*, Vol.A237, 7 Feb. 1938, pp.67-104.
- [35] M.J.McNutt and C.T.Sah, "High Frequency Space Charge Layer Capacitance of Strongly Inverted Semiconductor Surfaces," *Solid-State Electronics*, Vol.17, 1974, pp.377-385.
- [36] R.M.Swanson and J.D.Meindl, "Ion-Implanted Complementary MOS Transistors in Low-Voltage Circuits," *IEEE J. Solid-State Circuits*,

Vol.SC-7, No.2, April 1972, pp.146-153.

- [37] M.C.Tobey Jr. and N.Gordon, "Concerning the Onset of Heavy Inversion in MIS Devices," *IEEE Trans. Electron Devices*, Vol.ED-21, No.10, Oct. 1974, pp.649-650.
- [38] R.J.van Overstraeten, G.Declerck and G.L.Broux, "Inadequacy of the Classical Theory of the MOS Transistor Operating in Weak Inversion," *IEEE Trans. Electron Devices*, Vol.ED-20, No.12, Dec. 1973, pp.1150-1153.
- [39] S.G.Davison and J.D.Levine, "Surface States," *Solid-State Physics, Advances in Research and Applications*, Ed. H.Ehrenreich, F.Seitz and D.Turnbull, Academic Press, Vol.25, 1970.
- [40] J.Koomen, "Investigation of the MOST Channel Conductance in Weak Inversion," *Solid-State Electronics*, Vol.16, 1973, pp.801-810.
- [41] D.A.Antoniadis, S.E.Hansen and R.W.Dutton, "SUPREM-II: A Program for IC process modelling and simulation," *Technical Report SEL 78-020*, Stanford Electronics Laboratories, Stanford University, June 1978.
- [42] W.G.Oldham, S.N.Nandgaonkar, A.R.Neureuther and M.O'Toole, "A General Simulator for VLSI Lithography and Etching Process: Part I-Application to Projection Lithography," *IEEE Trans. Electron Devices*, Vol.ED-26, No.4, April 1979, pp.717-722.
- [43] T.Toyabe, K.Yamaguchi, S.Asai and M.S.Mock, "A Numerical Model of Avalanche Breakdown in MOSFET's," *IEEE Trans. Electron Devices*, Vol.ED-25, No.7, July 1978, pp.825-832.
- [44] D.P.Kennedy and R.R.O'Brien, "Analysis of the Impurity Atom Distribution Near the Diffusion Mask for a Planar p-n Junction," *IBM*

Journal, Vol.9, May 1965, pp.179-186.

- [45] H.G.Lee, J.D.Sansbury, R.W.Dutton and J.L.Moll, "Modeling and Measurement of Surface Impurity Profiles of Laterally Diffused Regions," *IEEE J. Solid-State Circuits*, Vol.SC-13, No.4, August 1978, pp.455-461.
- [46] C.Hastings, Jr., *Approximation for Digital Computers*, Princeton University Press, Princeton, N.J., 1955.
- [47] S.Liu, B.Hoefflinger and D.O.Pederson, "Interactive Two-Dimensional Design of Barrier-Controlled MOS Transistors," *IEEE Trans. Electron Devices*, Vol.ED-27, No.8, August 1980, pp.1550-1558.
- [48] L.M.Dang, "A Simple Current Model for Short-Channel IGFET and Its Application to Circuit Simulation," *IEEE J. Solid-State Circuits*, Vol.SC-14, No.2, April 1979, pp.358-367.
- [49] R.H.Dennard, F.H.Gaensslen, H.N.Yu, V.L.Rideout, E.B.Bassous and A.R.LeBlanc, "Design of Ion-Implanted MOSFET's with Very Small Physical Dimensions," *IEEE J. Solid-State Circuits*, Vol.SC-9, No.5, Oct. 1974, pp.256-268.
- [50] T.Nakamura, M.Yamamoto, H.Ishikawa and M.Shinoda, "Submicron Channel MOSFET's Logic Under Punchthrough," *IEEE J. Solid-State Circuits*, Vol.SC-13, No.5, October 1978, pp.572-577.
- [51] L.D.Yau, "A Simple Theory to Predict the Threshold Voltage of Short-Channel IGFET's," *Solid-State Electronics*, Vol.17, 1974, pp.1059-1063.
- [52] H.S.Lee, "An Analysis of the Threshold Voltage for Short Channel IGFET's," *Solid-State Electronics*, Vol.16, 1973, pp.1407-1417.

- [53] D.E.Ward and R.W.Dutton, "A Charge-Oriented Model for MOS Transistor Capacitances," *IEEE J. Solid-State Circuits*, Vol.SC-13, No.5, Oct. 1978, pp.703-708.
- [54] H.Masuda, M.Nakai and M.Kubo, "Characteristics and Limitation of Scaled-Down MOSFET's Due to Two-Dimensional Field Effect," *IEEE Trans. Electron Devices*, Vol.ED-26, No.6, June 1979, pp.980-986.
- [55] G.Merckel, J.Borei and N.Z.Cupcea, "An Accurate Large-Signal MOS Transistor Model for Use in Computer-Aided Design," *IEEE Trans. Electron Devices*, Vol.ED-19, No.5, May 1972, pp.681-690.
- [56] R.S.Muller and T.I.Kamins, *Device Electronics for Integrated Circuits*, John Wiley & Sons, 1977.
- [57] J.Bardeen and W.Shockley, "Deformation Potentials and Mobilities in Non-polar Crystal," *Physical Review*, Vol.80, 1950, pp.72-80.
- [58] E.Conwell and V.F.Weisskopf, "Theory of Impurity Scattering in Semiconductors," *Physical Review*, Vol.77, 1950, pp.388-390.
- [59] Y.C.Cheng and E.A.Sullivan, "On the Role of Scattering by Surface Roughness in Silicon Inversion Layers," *Surface Science*, Vol.34, 1973, pp.717-731.
- [60] A.R.Nelson and E.Brown, "Conduction in Quantized Silicon Inversion Layers with Many Occupied Subbands," *Physical Review B*, Vol.9, Feb. 1974, pp.1664-1668.
- [61] D.R.Alexander, R.J.Antinone and G.W.Brown, *SPICE2 MOS Modeling Handbook*, The BDM Corporation, BDM/A-77-071-TR, May 1977.

- [62] P.E.Cottrell, R.R.Troutman and T.H.Ning, "Hot Electron Emission in N-Channel IGFET's," *IEEE J. Solid-State Circuits*, Vol.SC-14, April 1979, pp.442-455.
- [63] G.T.Wright, "Current/Voltage characteristics, Channel Pinchoff, and Field-Effect Transistor," *Electronics Letters*, Vol.6, Feb. 1970, pp.107-109.
- [64] B.T.Murphy, "Unified Field Effect Transistor Theory Including Velocity Saturation," *IEEE J. Solid-State Circuits*, Vol.SC-15, June 1980, pp.325-328.
- [65] R.C.Foss, R.Hartland and J.Roberts, "An MOS Transistor Model for a Micro-Mini Computer Based Circuit Analysis System," *IEE Fifth European Solid-State Circuits Conference*, 1979, pp.56-57.
- [66] G.Baum and H.Beneking, "Drift Velocity Saturation in MOS Transistors," *IEEE Trans. Electron Devices*, Vol.ED-17, No.6, June 1972, pp.481-482.